

Low Temperature Co-fired Ceramics Technology for Power Magnetics Integration

Michele Hui Fern Lim

Dissertation submitted to the faculty of the
Virginia Polytechnic Institute and State University
in partial fulfillment of the requirements for the degree of

Doctor of Philosophy

In

Electrical Engineering

Jacobus Daniel van Wyk	Committee Co-Chair
Fred C. Lee	Committee Co-Chair
Guo-Quan Lu	Committee Member
Carlos Suchicital	Committee Member
Yilu Liu	Committee Member

17 November 2008
Blacksburg, Virginia

Keywords : Low temperature co-fired ceramics, power electronics, buck converter, magnetics, inductor, shielding, substrate

Low Temperature Co-fired Ceramics Technology for Power Magnetics Integration

Michele Hui Fern Lim

ABSTRACT

This dissertation focuses on the development of low-temperature co-fired ceramics (LTCC) technology for power converter magnetics integration. Because magnetic samples must be fabricated with thick conductors for power applications, the conventional LTCC process is modified by cutting trenches in the LTCC tapes where conductive paste is filled to produce thick conductors to adapt to this requirement. Characterization of the ceramic magnetic material is performed, and an empirical model based on the Steinmetz equation is developed to help in the estimation of losses at frequencies between 1 MHz to 4 MHz, operating temperature between 25 °C and 70 °C, DC pre-magnetization from 0 A/m to 1780 A/m, and AC magnetic flux densities between 5 mT to 50 mT. Temperature and DC pre-magnetization dependence on Steinmetz exponents are included in the model to describe the loss behavior.

In the development of the LTCC chip inductor, various geometries are evaluated. Rectangular-shaped conductor geometry is selected due to its potential to obtain a much smaller footprint, as well as the likelihood of having lower losses than almond-shaped conductors with the same cross-sectional area, which are typically a result of screen printing. The selected geometry has varying inductance with varying current, which helps improve converter efficiency at light load. The efficiency at a light-load current of 0.5 A can be improved by 30 %. Parametric variation of inductor geometry is performed to observe its effect on inductance with DC current as well as on converter efficiency.

An empirical model is developed to describe the change in inductance with DC current from 0 A to 16 A for LTCC planar inductors fabricated using low-permeability tape with conductor widths between 1 mm to 4 mm, conductor thickness 180 μm to 550 μm , and core thickness 170 μm to 520 μm . An inductor design flow diagram is formulated to help in the design of these inductors.

Configuring the inductor as the substrate carrying the semiconductor and the other electronic components is a next step to freeing the surface area of the bulky component and improving the power density. A conductive shield is introduced between the circuitry and the magnetic substrate to avoid adversely affecting circuit operation by having a magnetic substrate in close proximity to the circuitry. The shield helps reduce parasitic inductances when placed in close proximity to the circuitry. A shield thickness in the range of 50 μm to 100 μm is found to be a good compromise between power loss and parasitic inductance reduction. The shield is effective when its conductivity is above 10^7 S/m. When a shield is introduced between the inductor substrate and the circuitry, the sample exhibits a lower voltage overshoot (47 % lower) and an overall higher efficiency (7 % higher at 16 A), than an inductor without a shield. A shielded active circuitry placed on top of an inductive substrate performs similarly to a shielded active circuitry placed side-by-side with the inductor. Using a floating shield for the active circuitry yields a slightly better performance than using a grounded shield.

To my parents

Sen Kee Lim

Sin Ting Wee

ACKNOWLEDGEMENTS

I would like to express my gratitude and appreciation to the following people, without whom the completion of the dissertation will not be possible:

- Professor J. D. van Wyk, my academic advisor and mentor, for the invaluable advice, unconditional support in guiding me to conduct and complete the research, and the valuable discussions I had with him throughout the course of the research. I'm very grateful for his accessibility and effort he has put into advising me. His comprehension of things in breadth as well as depth has always amazed me. His sincere appreciation of all ideas as good ideas is an inspiring role model for us.
- Professor Fred C. Lee, for his open-mindedness and inspiring attitude of embracing failure in the pursuit of success, his time spent on the valuable discussions I had with him during the course of the project.
- Dr. Z. Liang for his training, expertise and help during his presence in CPES.
- Professor G. Q Lu for his help and advice on the material aspects of this project.
- Professor C. Suchicital for his help and advice in using the necessary equipment in the early stage of this work.
- Mr. Dan Huff and Bob Martin for their help and training in the use of equipment, which helps me get things done smoothly.
- Mrs. Teresa Rose for helping in the purchase of the materials and equipment required for this research.
- Mr. David Gilham for preparing some of the samples for this research.

- The faculty and colleagues in the Integrated Power Supply (IPS) group, Professor M. Xu, Professor K. Ngo, Dr. K. Yao, Dr. L. Zhao, Dr. Y. Ren, Mr. Y. Meng, Mr. D. Sterk, Mr. A. Ball, Mr. J. Sun, Mr. Y. Dong, Mr. Q. Li, Dr. A. Sharma, Dr. X. Wu and many others. I am grateful and am humbled to have the opportunity to work with such a talented group.
- All the other faculty, staff and students in CPES who has helped the author in one way or another and for their friendship.
- My relatives in the United States Mr. and Mrs. Liu for their help when I first came to the United States.
- My family for their support and encouragement during my stay in the United States.
- The National Science Foundation for their financial support.

TABLE OF CONTENTS

	<u>Title</u>	<u>Page</u>
	Abstract	ii
	Dedication	iv
	Acknowledgements	v
	Table of Contents	vii
	List of Figures	xi
	List of Tables	xviii
	List of Symbols	xix
1.	A Review of Possible Technologies for Low Profile Power Electronics Integration	1
1.1	Available Technologies for Power Supply Integration	1
1.2	Evaluation of the Scalability of These Technologies for Power Magnetics Integration	5
1.3	Choosing LTCC: Attractive Attributes due to Thermo-mechanical Characteristics	8
1.4	Choosing LTCC: The Power Magnetics Challenge	9
1.4.1	Suitability of LTCC for high current applications	10
1.4.2	Low profile Magnetics	10
1.4.3	Thermal and Mechanical Considerations	11
1.5	Motivation	12
1.6	Objectives	12
1.7	Organisation of Dissertation	13
2.	Processing Technology for Low Profile Power Magnetics	16
2.1	Overview of Existing LTCC Processing Technology	16
2.2	Thin Samples	18
2.2.1	Warping of Thin Samples	18
2.2.2	Weight Application during Sintering for Thin Samples	20
2.2.3	Application of Alumina powder	21
2.3	Thick Samples	23
2.3.1	Circumferential cracking of thick samples	23
2.3.2	Are circular samples the solution to avoid circumferential cracking?	24
2.3.3	Sintering thick samples	27
2.4	Choice of Metallization	29
2.4.1	Possibility of Using Copper with LTCC	29
2.4.2	Reduction of copper oxide to copper	32
2.4.3	Sintering LTCC tape with sandwiched alumina strips	34
2.4.4	Using Copper Paste	36
2.4.5	Using Ag/Pt Paste	37

2.4.6	Alternative cross-sectional shapes for conductors	38
2.4.7	Power Inductor Fabrication Procedure	39
2.4.7.1	Single Conductor Inductor	39
2.4.7.2	Multi-Conductor Inductor	42
2.4.8	Conductivity and Solderability Improvement	43
2.5	Conclusions for Chapter 2	44
3.	Material Characterization for Power Magnetics	47
3.1	Overview	47
3.2	Estimation of Permittivity	47
3.2.1	Sample Preparation	48
3.2.2	Permittivity Measurement	49
3.3	Estimation of Core Loss	51
3.3.1	Circuit for Loss Measurement	51
3.3.2	Components in Circuitry for Loss Measurement	52
3.3.2.1	Toroidal Core for Loss Measurement	53
3.3.2.2	Toroidal Core Windings	59
3.3.2.3	Resonant Capacitor	64
3.3.2.4	Current Sense Resistors	66
3.3.2.5	DC Blocking Capacitor	67
3.3.2.6	AC choke	67
3.4	Sources of Measurement Error	69
3.4.1	Error due to Oscilloscope	69
3.4.2	Error due to Probe / Cable	70
3.4.3	Error due to Current Sense Resistor	74
3.4.4	Error due to Noise in Measurement	75
3.4.5	Error due to Phase Shift between V and I	75
3.4.6	Summary	76
3.5	Operational Influence on Electromagnetic Characteristics of LTCC Magnetic Material	80
3.5.1	Effect of Frequency on Electromagnetic Characteristics	81
3.5.2	Effect of Pre-Magnetization on Electromagnetic Characteristics	82
3.5.3	Effect of Temperature on Electromagnetic Characteristics	84
3.5.4	Model Comparison with Actual Data	88
3.6	Electrical Characterization of Conductive Paste	93
3.7	Summary	96
4.	LTCC Chip Inductor Development	97
4.1	Overview	97
4.2	Geometry Selection for Integratable Chip Inductor	97
4.2.1	Comparison of Various Geometries of Planar Inductor	97
4.2.1.1	Toroidal coil inductor	98
4.2.1.2	Solenoid inductor	98
4.2.1.3	Racetrack or spiral inductor	99
4.2.1.4	Meander inductor	100

4.2.1.5	Short winding inductor	101
4.2.1.6	Summary	102
4.2.2	Concept of Varying Inductance with Bias for Chosen Geometry	102
4.2.3	Impact of Varying Inductance on Circuit Performance	103
4.3	Conductor Cross-Sectional Shape Study for Chosen Geometry	106
4.3.1	Simulation of Conductors with Various Cross-Sectional Shapes	106
4.3.1.1	Conductors in Air	107
4.3.1.2	Conductors in Magnetic Medium	110
4.3.1.3	Final Selection of Generic Geometry	113
4.3.2	Experimental Study	114
4.4	Circuit Specifications for Chip Inductor	118
4.5	Geometry of LTCC Chip Inductor for Model Development	119
4.6	Parametric Variation of Inductor Geometry	120
4.6.1	Effect of Varying Conductor Width	120
4.6.2	Effect of Varying Core Thickness	126
4.6.3	Effect of Varying Conductor Thickness	130
4.6.4	Effect of Varying Number of Parallel Conductors	132
4.7	Inductance Model for LTCC Inductor	135
4.8	Inductor Design Procedure	140
4.9	Summary	145
5.	LTCC Inductor as Substrate	147
5.1	Overview	147
5.2	Circuit Specifications	148
5.3	Geometry of Integrated Inductor	148
5.4	Substrate Inductor Design Procedure	149
5.5	Effect of LTCC Inductor as Substrate	156
5.5.1	Inductor Substrate Fabrication Procedure	156
5.5.2	Large Signal Measurement Results	159
5.6	Review of Electromagnetic Shielding Techniques	161
5.7	LTCC Inductor Substrate with Metal Shield	162
5.7.1	Simulation Study of Shielding for Magnetic Substrate	162
5.7.1.1	Comparison Between with and without Shield	163
5.7.1.2	Effect of Varying Shield Distance from Conductor	166
5.7.1.3	Effect of Varying Shield Thickness	166
5.7.1.4	Effect of Varying Shield Conductivity	168
5.7.2	Shielded Inductor Substrate Fabrication Procedure	169
5.8	Experimental Study of Substrate Structures	174
5.8.1	Samples Fabrication Procedure	177
5.8.2	Experimental Prototypes	179
5.8.3	Metrics Comparison	182
5.8.3.1	Percentage overshoot of voltage across top and bottom MOSFETs	184
5.8.3.2	Switching Loss	185

5.8.3.3	Efficiency	188
5.8.3.4	Gate Drive Input Power	189
5.8.3.5	Summary	190
5.9	Summary	190
6.	Conclusion And Further Work	192
6.1	Conclusion	192
6.2	Further Work	194
	Appendix	195
	Reference	197

List of Figures

<u>Figure</u>	<u>Title</u>	<u>Page</u>
2-1	Typical LTCC process flow	17
2-2	Sintering profile for LTCC samples	19
2-3	Single layer LTCC ferrite tapes (a) before and (b) after sintering, without applying weight during sintering	20
2-4	LTCC ferrite tape with dimensions of 8 mm x 8 mm after sintering, applying weight during sintering. (a) Single layer, (b) two laminated layers and (c) four laminated layers.	21
2-5	Two-layered laminated ferrite tape samples after sintering. (a) Sample sintered between alumina tiles without applying powder on the tiles or sample, (b) sample with a non-uniform layer of alumina powder applied, (c) sample with a thin layer of alumina powder applied.	23
2-6	LTCC ferrite tape after sintering, applying weight during sintering. Sample (a) comprises four layers of laminated LTCC tape and has alumina powder applied. Sample (b) comprises eight layers of laminated LTCC tape and does not have alumina powder applied to the sample.	24
2-7	Circular samples of diameter 20 mm with (a) 4 layers, (b) 10 layers and (c) 20 layers of ferrite tape. Weight is applied during sintering.	25
2-8	Fabrication procedure of 20-layered samples of LTCC ferrite tape with embedded conductor patterns. (a) Circular sample with U-shaped conductor, (b) capsule shaped sample with straight conductor applying weight (3 pieces of alumina tile) during sintering.	26
2-9	Fabrication procedure of single-conductor inductors without applying weight during sintering	28
2-10	Twenty-layered rectangular samples of LTCC ferrite tape with embedded conductor (a) before and (b) after sintering	28
2-11	Drawing of sample with copper strip sandwiched between two layers of ferrite tape	30
2-12	Samples of copper strip sandwiched in two layers of ferrite tape fired under (a) oxidizing (air) ambient, (b) reducing ambient (H_2/N_2) and (c) inert ambient (Ar).	30
2-13	Square toroid samples fired under (a) oxidizing (air) ambient, (b) reducing ambient (H_2/N_2) and (c) inert ambient (Ar).	31
2-14	Sintering profile conducted in air followed by reducing profile conducted in H_2/N_2 .	33
2-15	Cross-sectional view of copper (a) before oxidation, (b) after oxidation, (c) followed by reduction	34
2-16	Thin alumina strips sandwiched in LTCC ferrite tape (a)	35

	before and (b) after sintering.	
2-17	Cross-sectional view of thin alumina strip sandwiched in LTCC ferrite tape after sintering.	35
2-18	Sheet resistance of sintered copper paste vs. fired thickness	36
2-19	Cross-sectional view of screen-printed conductors embedded in LTCC tape after sintering.	38
2-20	LTCC inductor fabrication procedure. (a) Bottom Layer, (b) middle layer, (c) laminate bottom and middle layers, (d) Fill slot with conductor paste, (e) dry conductor paste at 80 °C, laminate (e) with top layer (f), (g) Fill slots with conductor paste and laser cut into desired shape, (h) inductor after sintering.	40
2-21	Sintering profile for LTCC inductor samples with reduced 1 st ramp rate (region I)	41
2-22	Fabrication procedure for multi-conductor inductor with number of parallel conductors, $n = 1$ to 3	43
2-23	Electrodes of inductor electroplated with copper to improve solderability	44
3-1	Capacitor samples for dielectric constant estimation	49
3-2	Graph of admittance vs. frequency for the two parallel plate capacitor samples	50
3-3	Core loss measurement circuit	52
3-4	Percentage error in specific core loss vs. r_i / r_o	56
3-5	Percentage error in specific core loss vs. β for $r_i / r_o = 0.5$, 0.75 and 0.9	56
3-6	Power loss vs. r_o , for $r_i / r_o = 0.8$ and $h = 2$ mm	57
3-7	Geometry of toroidal core. (a) Top view, (b) cross-sectional view	58
3-8	Actual toroidal core for loss measurement	59
3-9	Percentage magnitude error vs. inductance at 4 MHz	60
3-10	Toroidal core for loss measurement. (a) Position of thermocouple on core, (b) toroidal core connection with circuit via copper straps.	63
3-11	Impedance characteristics of a 100 μ F ceramic capacitor and a 100 μ F electrolytic capacitor	67
3-12	Impedance characteristics of AC choke (a) Magnitude vs. frequency, (b) phase vs. frequency.	68
3-13	Equivalent circuit of voltage measurement across secondary side of transformer	71
3-14	Percentage magnitude error due to resonance between inductance of coil ($L = 3$ μ H) and input capacitance of probe.	71
3-15	Percentage magnitude error vs. inductance using oscilloscope probe P5050 with input capacitance of 11.1 pF	72
3-16	Equivalent circuit of voltage measurement across current sense resistor	74
3-17	Oscilloscope screen with the noise band and the offset voltage	75

3-18	Power loss measurement error vs. phase shift between V and I for phase error of 0.1°, 1° and 10°	76
3-19	Percentage power error vs. phase shift between current through primary coils and voltage across secondary coils for 1 MHz and 4 MHz, considering total magnitude error and total phase error	80
3-20	Specific power loss vs. peak-to-peak flux density for frequencies between 1 to 5 MHz at $T = 26\text{ °C}$ and $I_{DC} = 0\text{ A}$	82
3-21	Graph of $\log(K_p \cdot f^\alpha)$ vs. $\log(f)$ at $T = 26\text{ °C}$ and $I_{DC} = 0\text{ A}$	82
3-22	Graph of β vs. I_{DC} at $T = 26\text{ °C}$.	83
3-23	Graph of $\log(K_p \cdot f^\alpha)$ vs. I_{DC} at $T = 26\text{ °C}$	83
3-24	Graph of α vs. I_{DC} at $T = 26\text{ °C}$	84
3-25	Graph of K_p vs. I_{DC} at $T = 26\text{ °C}$	84
3-26	Graphs of (a) α vs. I_{DC} , (b) β vs. I_{DC} , and (c) K_p vs. I_{DC} for $T = 26, 50$ and 70 °C	86
3-27	Graphs of (a) a_1 vs. T , (b) a_2 vs. T , (c) b_1 vs. T , (d) b_2 vs. T , (e) k_1 vs. T , (f) k_2 vs. T	86
3-28	Specific power loss vs. peak-to-peak flux density and or frequencies between 1 to 5 MHz at $T = 26\text{ °C}$ and $I_{DC} = 0\text{ A}$	89
3-29	Percentage error between fitted curves and experimental data, for frequencies between 1 to 5 MHz at $T = 26\text{ °C}$ and $I_{DC} = 0\text{ A}$	89
3-30	Percentage error between experimental data and model vs. peak-to-peak flux density for (a) 1 MHz, (b) 2 MHz, (c) 3 MHz and (d) 4 MHz, at 26 °C , 50 °C , 70 °C and $I_{DC} = 0\text{ A}$ and 3 A	90
3-31	Percentage power error vs. phase shift between current through primary coils and voltage across secondary coils for 1 MHz and 4 MHz, considering total magnitude error and total phase error. Range of phase shift for 1 MHz and 4 MHz are indicated	91
3-32	Percentage power error vs. peak-to-peak flux density, B_m for (a) $f = 1\text{ MHz}$ and (b) $f = 4\text{ MHz}$, considering measurement error discussed in section 3.4	92
3-33	Sintering profile for Ag/Pt paste	94
3-34	Cross-sectional view of the inductors (a) L_1 and (b) L_2	94
3-35	Cross-sectional area approximation of screen-printed Ag/Pt conductor using (a) segment of a circle and (b) triangle	95
4-1	Toroidal coils on LTCC NiCuZn ferrite substrate	98
4-2	Planar inductor with micromachined NiFe magnetic bar	99
4-3	On-chip racetrack winding inductor using NiFe magnetic core	100
4-4	Vertical stacked spiral inductor for RFIC applications	100
4-5	Thick film meander inductor	101
4-6	V-groove inductor embedded in silicon	102
4-7	Cross-sectional diagram of thick film planar inductor	102
4-8	Illustration of changing inductance with DC current for non-	103

	linear inductor L_2 in comparison with a linear inductor L_1 with constant inductance with DC current.	
4-9	Buck converter circuit diagram	104
4-10	Inductor current when inductance is higher at light load and lower at heavy load.	104
4-11	Current waveform of the top switch for (a) small filter inductance and (b) large filter inductance	105
4-12	Power stage efficiency vs. DC current for linear inductor L_1 and non-linear inductor L_2 .	105
4-13	Comparison of conductor cross-sectional shapes, (a) almond, (b) capsule, and (c) rectangular, for a cross-sectional area of 0.1 mm^2 .	107
4-14	2-D current density distribution for (a) capsule shaped, (b) rectangular shaped and (c) almond shaped conductors in air. Frequency = 4 MHz.	108
4-15	1-D current density along dotted line for capsule and almond conductor cross-sectional shapes in air. Frequency = 4 MHz.	109
4-16	Conduction power loss per unit length for various conductor shapes in air	110
4-17	1-D current density along dotted line for (a) capsule and (b) almond conductor cross-sectional shapes, surrounded by magnetic material. Frequency = 4 MHz	112
4-18	Conduction power loss per unit length for conductors surrounded by magnetic core of $\mu_r = 60$ and $\epsilon_r = 13$	112
4-19	Core loss per unit length for conductors surrounded by magnetic core of $\mu_r = 60$ and $\epsilon_r = 13$	113
4-20	Cross-sectional view of LTCC inductors with (a) rectangular and (b) almond cross-sectional shape	115
4-21	LTCC inductor tested on prototype Buck converter. The temperature of the inductor is measured using a K-type thermocouple attached to the back of the inductor	116
4-22	Cylindrical column placed over the inductor to minimize the effect of the fan on temperature measurements	117
4-23	Inductor voltage and current waveforms	117
4-24	Inductance and temperature rise comparison for the rectangular and almond conductor cross-sectional shapes at full load ($I_{DC} = 5\text{A}$).	118
4-25	Three-dimensional view of LTCC planar inductor	119
4-26	Dimensions of LTCC inductor.	121
4-27	Cross-sectional view of LTCC inductors with conductor widths ranging from 1 mm to 5 mm	121
4-28	Change of inductance with output current	122
4-29	Inductor current waveforms comparison (a) at light load current of 1 A and (b) at full load current of 12.5 A, for LTCC inductor with conductor width 1 mm and commercial inductor of effective inductance 23 nH. $V_{in} = 5 \text{ V}$, $V_o = 1.1 \text{ V}$.	123

4-30	Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for conductor width variation between 1 mm to 5 mm	125
4-31	Change of inductance with output current for conductor width, (a) $w = 2$ mm, (b) $w = 3$ mm, (c) $w = 4$ mm, conductor thickness, $e = 0.4$ mm and core thickness, g , varying between $173 \mu\text{m}$ to $520 \mu\text{m}$	127
4-32	Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for core thickness variation between $173 \mu\text{m}$ to $520 \mu\text{m}$ for $w = 2$ mm.	128
4-33	Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for core thickness variation between $173 \mu\text{m}$ to $520 \mu\text{m}$ for $w = 3$ mm	129
4-34	Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for core thickness variation between $173 \mu\text{m}$ to $520 \mu\text{m}$ for $w = 4$ mm	130
4-35	Change of inductance with output current for conductor width, $w = 3$ mm, core thickness, $g = 0.4$ mm and conductor thickness, e , varying between $260 \mu\text{m}$ to $550 \mu\text{m}$	131
4-36	Power stage efficiency vs. output current using inductors with conductor width, $w = 3$ mm, core thickness, $g = 0.4$ mm and conductor thickness, e , varying between $260 \mu\text{m}$ to $550 \mu\text{m}$	132
4-37	Change of inductance with output current	133
4-38	Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load, for multi-conductor inductor	135
4-39	Graph of $\log(\mu_r)$ vs. I_{DC} for inductors of conductor widths varying from 1 mm to 5 mm.	137
4-40	Graph of (a) coefficient ' a ', and (b) coefficient ' b ' of equation (4-7) vs. conductor width	137
4-41	Graph of $\log(\mu_r)$ vs. I_{DC} for inductors of various core thickness, g , for conductor widths of (a) 2 mm and (b) 3 mm and (c) 4 mm.	139
4-42	Graph of $\log(\mu_r)$ vs. I_{DC} for inductors of various conductor thickness, e .	139
4-43	Flow diagram for LTCC inductor design	141
4-44	Footprint of the inductor and the position of the electrodes	142
4-45	Graph of conductor thickness, e , vs. conductor width, w , for $L = 25$ nH	144
4-46	Graph of resistance, R , vs. conductor width, w .	144
5-1	Buck converter circuit diagram	148
5-2	LTCC inductor substrate. (a) Three-dimensional view of LTCC planar inductor, (b) cross-sectional diagram of LTCC planar inductor	149
5-3	Flow diagram for LTCC inductor substrate design	150
5-4	Footprint of the inductor and the position of the electrodes. Windings must avoid the through hole in the structure.	151

5-5	Design of winding for LTCC inductor example	152
5-6	Graph of conductor thickness, e , vs. conductor width, w , for $L = 105$ nH	154
5-7	Graph of resistance, R , vs. conductor width, w .	155
5-8	Inductor substrate fabrication procedure.	158
5-9	Buck converter on inductor substrate.	159
5-10	V_{GS} of the top and bottom MOSFETs (a) before (b) after connecting gate driver directly to the gate of the bottom MOSFET via copper strip.	161
5-11	Simulation structure with conductive shield between the conductive trace and magnetic substrate.	164
5-12	Cross-sectional drawings of simulation structures.	165
5-13	Normalized power losses for the four cases	165
5-14	Normalized loop inductances for the four cases	165
5-15	Graph of power loss and inductance vs. insulator thickness. Both the conductor thickness and shield thicknesses are 70 μm .	167
5-16	Graph of power loss and inductance vs. shield thickness. The conductor thickness is 70 μm and insulator thicknesses are 50 μm .	167
5-17	Graph of energy stored and power loss vs. shield conductivity. Conductor thickness and insulator thickness are both 50 μm . Shield thickness is 10 μm . Simulation frequency is 1.3 MHz.	168
5-18	Fabrication procedure of inductor substrate. (a) Bottom main layer comprising 7 layers of ferrite tape, (b) Middle main layer comprising 8 layers of ferrite tape. An S-shape slot is cut using laser machining. (c) Top main layer comprising 7 layers of ferrite tape. Two rectangular slots for inductor's electrode cut using laser machining, (d) Laminate (a) with (b), (e) Ag/Pt paste is dispensed into the slot as described in Fig. 4-5. (f) Laminate (c) with (e), fill rectangular slots with Ag/Pt paste and sinter.	170
5-19	Trace layers for sample (a) with no shield and (b) with shield.	171
5-20	Improved prototype Buck converter with inclusion of metal shield above magnetic substrate. The red dotted line shows the shape of the metal shield, which is below the circuitry.	172
5-21	Waveforms of V_{DS} of bottom MOSFET in Buck converter for sample with (a) no shield and (b) with shield, at no load	172
5-22	Power stage efficiency vs. output current for sample with shield and without shield, measured according to the methods of the circuits in Fig. 5-9.	173
5-23	Surface mount devices and components, with pyralux carrier and substrate inductor. (a) 3-D view (b) 2-D lay-up diagram of pyralux carrier and substrate inductor.	177
5-24	Pyralux layer with circuit layout on top layer, with and without shield on flipped layer	178

5-25	Prototype buck converter with integrated shield and inductor (a) as substrate, (b) inductor placed on the side of active circuitry	180
5-26	Inductor voltage and current waveforms	181
5-27	Inductance vs. output current for the case of inductor side-by-side with the active circuit and inductor as substrate to the active circuit.	181
5-28	V_{DS} of top MOSFET for the six cases. The frequency is 1.3 MHz and the average current is around 16 A.	183
5-29	V_{DS} of bottom MOSFET for the six cases. The frequency is 1.3 MHz and the average current is around 16 A.	184
5-30	Loop inductance comparison for inductance obtained from simulation and derived from experimental results for the four cases.	187
5-31	Power stage efficiency vs. I_{out} for the six cases	189
A-1	Illustrations for derivations. (a) Cross sectional drawing, (b) plan view drawing and (c) magnetic flux density illustration for toroidal core	195

List of Tables

<u>Table</u>	<u>Title</u>	<u>Page</u>
1-1	Planar Integration of Magnetics in Technologies For Various Applications	3
1-2	Range of Values of Parameters Under Typical Operating Conditions For RF and Power Electronics Applications	6
1-3	Comparison of The Thermo-Mechanical Properties of Silicon, LTCC and PCB	9
3-1	Core Dimensions	58
3-2	Total Core Dimensions	59
3-3	I_{peak} for wires of AWG between 23 and 27	61
3-4	AC resistance per unit Length of AWG 25 wire and Resistance of primary Windings at various Frequencies	63
3-5	Types of Capacitors and their ESL, ESR and R_p	65
3-6	Required Parallel Resonant Capacitors, C_1 , for Each Frequency	66
3-7	Input capacitance, resonant frequency and magnitude error for measuring voltage across a 3 μ H inductor	72
3-8	Propagation delay and phase error for a 2 feet coaxial cable and the P6134 and P6243 oscilloscope probes	73
3-9	Summary of Magnitude Error	77
3-10	Summary of Phase Error	78
3-11	Resistance Measurement Of Screen-Printed Conductors	95
3-12	Estimated Conductivity Of The Screen-Printed Conductor Paste Using The Two Methods	95
4-1	Loss comparison for conductors with almond, rectangular and capsule cross-sectional shapes at $f = 4$ MHz and $I = 1$ A	113
4-2	Specifications For Inductor	142
4-3	Inductor Design Values	145
5-1	Specifications For Substrate Inductor	151
5-2	Substrate Inductor Design Values	156
5-3	Parts Used In Fabrication Of Prototype	160
5-4	Commercial Buck Regulators With Integrated Inductor And Load Currents In The Ampere Range	175
5-5	Comparison Of Cases With Substrate Inductor And Co-Packaged Inductor	176
5-6	Parts Used In Fabrication Of Prototype	179
5-7	Voltage Overshoot Comparison Using Case A1 As The Base For Comparison.	184
5-8	Loop Inductance and Power Loss Comparison At $I_{out} = 16$ A	186
5-9	Gate Drive Loss Comparison at $I_{out} = 16$ A	190

List of Symbols

f	Frequency
Y	Admittance
C	Capacitance
L	Inductance
R	Resistance
V	Voltage
I	Current
B	Magnetic flux density
H	Magnetic flux intensity
r	Radius
r_i	Inner radius
r_o	Outer radius
h	Thickness
P_v	Specific core loss
t	Time
α	Steinmetz exponent, alpha
β	Steinmetz exponent, beta
K_p	Steinmetz Coefficient
OD	Outer diameter
ID	Inner diameter
l_m	Average magnetic path length
C_{in}	Input capacitance
μ_0	Permeability of free space
μ_r	Relative permeability
μ	Magnetic permeability
A	Area
n	Number of turns
B_m	Peak-to-peak flux density
w	Width of conductor
e	Thickness of conductor
g	Thickness of core
l_{wire}	Length of wire
R_{ac}	AC resistance
R_{dc}	DC resistance
H_{AC}	AC magnetic flux intensity
H_{DC}	DC magnetic flux intensity
I_{max}	Maximum current
J_{max}	Maximum current density
R_P	Equivalent parallel resistance
Q	Quality factor
C_1	Parallel resonant capacitance
C_2	DC blocking capacitance
L_1	Inductance of AC choke
R_{sense}	Effective resistance of sense resistors

L_{sense}	Equivalent series inductance of sense resistance
ESL	Equivalent series inductance
θ	Phase shift between voltage and current
ΔP	Small change in power
ΔI	Small change in current
ΔV	Small change in voltage
$\Delta \theta$	Small change in phase shift
I_{DC}	DC current
T	Temperature in degree Celsius
σ	Conductivity
ρ	Resistivity
I_{LL}	Light load current
I_{HL}	Heavy load current
I_{top}	Current through top switch
Δi	Current ripple
D	Duty cycle
η	Efficiency
J	Current density
A	Area
P	Power
l	Length
ϵ_0	Permittivity of free space
ϵ_r	Relative permittivity
V_o	Output voltage
V_i	Input voltage
I_o	Output current
I_i	Input current

Chapter 1. A Review of Possible Technologies for Low Profile Power Electronics Integration

1.1 Available Technologies for Power Supply Integration

Recently, power electronics systems performance has been dictated by improvements in semiconductor devices [1, 2]. With miniaturization and improvements in device performance, the development of power electronic systems has progressed to the state where active devices are no longer the major contributing factor to the system's size and cost [3-5]. Instead, passive components constitute most of the size and cost of power electronics systems at present. With the demand to improve the transient performance of a system, reduction in parasitic inductances becomes necessary. Hence, the integrated manufacturing of magnetic and dielectric components has started to take on an increasingly important role in power electronics systems [3-5].

Currently, active devices in power electronics modules are interconnected by wire-bonding or by solder bumps on the device pads. However, amongst the new technologies being developed for active device interconnects, the planar metallization device interconnects have been one of the most promising, as the technology allows for three-dimensional integration of active devices with passive components [6]. Furthermore, a range of technologies are at present being actively researched for manufacturing low-profile passive devices (inductors and capacitors) and integrating them with the active devices in a three-dimensional way for a range of applications, from RF to power electronics. Table 1-1 lists the reference numbers of the various papers in the literature

that address the various planar integration technologies used in various applications for manufacturing the passives, particularly magnetic components.

For RF applications, the inductors used are usually in the form of a planar coil [7], a three-dimensional spiral [8-10], or a meandering form [11] with inductance ranging from a few hundred pH to a few tens of nH, and with operation frequency in the GHz range. The inductors can be air core inductors [12] or built in a magnetic medium [13], and the magnetic core can be in the form of a laminate [9] if built in a printed circuit board (PCB). For on-chip inductors, thin ferrite films can be fabricated using spin coating combined with the sol-gel process and rapid thermal annealing (RTA) [13]. For low temperature co-fired ceramics (LTCC), the product is usually sintered at around 900 °C [14, 15]. Powder blasting of commercially available ferrites can be combined with coils built on flexible foil to make inductors [16]. For metallization, copper is used for PCB, on-chip, and flexible substrate magnetics integration. Silver and its alloys or gold [15] is usually used for LTCC.

In power electronics applications, the inductors can take the form of a planar coil [17, 18], a three-dimensional spiral [19, 20], a planar toroidal coil [21] or a V groove etched into the silicon [22]. The power ranges from a few watts [19] to several tens of watts [18]. The operating frequency ranges from several hundreds of kilohertz [18, 23], a few megahertz [21, 24, 25] to several tens of megahertz [11, 13]. The power densities can range from a few hundreds [23] to a couple of thousands [26] of watts per cubic inch. For inductors integrated in a PCB, the magnetic core can be commercial [17], made from ferrite polymer compounds (FPC) [18], which typically has low magnetic permeability of $\mu_r = 10$ to 20, iron foil [18] for higher magnetic permeability, or electroplated NiFe [19].

For inductors made using LTCC tapes, the magnetic material can be NiCuZn [21, 25, 27] or NiZn [28]. For on-chip inductors, electroplated NiFe [29, 30], deposited CoZrO [22], FeAlO and CoFeBSiO [22] or ion-beam-sputtered CoZrRe [31, 32] can be used. For inductors made using a flexible substrate, the core can be screen-printed ferrite polymer composite [24] or a commercial substrate [23, 26].

PCB, LTCC, on-chip and flexible substrates have been demonstrated to be useful for various filter applications. Transformers can be built on PCBs to nullify the equivalent series inductance (ESL) of the capacitor to improve the high-frequency performance of a filter [33]. Low temperature co-fired ceramic technology has been used to build a filter for satellite systems [34]. On-chip bond wire inductors have been developed for RF filter applications [35]. An integrated passive filter built using flexible polymer substrate and commercial core has been developed [36].

Table 1-1 Table of References for Planar Integration of Magnetic Components For Various Applications

		Substrate			
		PCB	LTCC	On- chip	Flexible substrate
Application	RF/ microwave	[7-10]	[14, 15]	[12, 13]	[16]
	Power electronics	[17-20]	[21, 25, 27]	[22, 29-32]	[24, 26]
	Filters	[33]	[34]	[35]	[36]

Using LTCC technology for power electronic applications is a new area. This is partly attributed to the limitation of the current LTCC processing technology for high-

current applications [37], as well as continued concentration on solutions where inductors are deposited on the silicon chip [9-14], which currently dominate low-power applications. The major limitation of using the current LTCC technology for high-current applications is the small cross-sectional area of screen-printed conductors, which results in high resistance. Additionally, due to the presence of additives like glass in the silver alloy paste, the resistivity is usually two to three times larger than that of copper. Furthermore, the LTCC ferrite tapes are currently not co-fireable with non-ferrite tapes, which further limit its applications. There is some work related to using LTCC technology for power electronic applications reported in the literature, but these are limited to currents of less than 1 A [21, 25, 27].

Despite the various limitations of the current LTCC technology, using LTCC technology for power electronics hybrid integration does provide various advantages in terms of thermal coefficient of expansion (CTE) matching with silicon [38], the potential for higher power conversion, since it is a thick-film-based technology, and there are readily available magnetic and dielectric materials suitable for megahertz converter operation, since the technology has been widely used in high-frequency applications [14, 34]. In addition, the thermal conductivity of LTCC (2.5 to 4.0 W/m °K) is around 10 times higher than that of PCB (0.2 to 0.3 W/m °K), which makes LTCC a good candidate for power electronics applications. Furthermore, thermal vias can be added to the LTCC module to improve the thermal conductivity further.

1.2 Evaluation of the Scalability of the Available Technologies for Power Magnetics Integration

The available technologies under comparison in Table 1-1 can be used for RF / microwave and filter applications but they are very limited for power electronic applications. The fundamental differences between RF and power electronics applications lie in the power level as well as the frequency range. For passive components like the inductor or transformer, the current capability requirement is also vastly different. Though the same technology can be used for both applications, the materials used, the processing technique, the dimensions of the components, and the range of values of the electrical parameters are different. Special attention needs to be given to the dimensions, since power electronics applications require conductor dimensions and magnetic layer thicknesses that are larger by an order of magnitude or more, implying important processing development. Table 1-2 compares the differences between the inductance, frequency range, current range and medium for RF and power electronics applications.

From the differences in the operating range of the inductor used in RF and power electronics applications, the physical dimensions of the windings and core will be different. For instance, for low-current applications, the winding's cross-sectional area can be small. For higher-current applications, the winding's cross-sectional area has to be sufficiently large to reduce ohmic losses in the windings, since ohmic losses scale with the square of the current. For RF applications, the operating frequency is in the GHz range. Hence, RF inductors usually have an air core, since most available magnetic materials are specified for use at much lower frequencies. Moreover, core loss is related

to frequency by the power law (to be discussed in Chapter 3), which makes the use of a magnetic medium less attractive for GHz operation. However, there are also some magnetic materials suitable for GHz operation, which are usually of very low magnetic permeability [39].

Table 1-2 Range of Values of Parameters Under Typical Operating Conditions for RF and Power Electronics Applications

	RF / Microwave	Power Electronics
Inductance	pH – nH	nH - μ H
Frequency	GHz	kHz – MHz
Current	nA - μ A	mA – A
Core	Air	Magnetic medium
Efficiency	Low (typically < 50 %)	Decisive importance (usually > 80 %)

For PCB and flexible substrate technology, copper is the conductor of choice. The copper sheet is usually mechanically bonded to the polymer substrate material at a relatively low processing temperature (< 200 °C). The thickness of the copper required can be chosen according to the requirements. For on-chip integrated inductors, the metallization can be aluminum or copper. For very-low-current applications, the copper is usually sputtered and has a thickness of less than 1 μ m. For higher-current applications, copper is usually used and is normally electroplated. However, due to thermo-mechanical and reliability limitations, the thickness of the copper electroplated on silicon is usually limited to several tens of μ m [40]. This limits the maximum current for

optimal performance. To overcome the problem of oxidation, the metallization can be plated with nickel followed by gold. For LTCC technology used for RF applications, the conductors are usually in paste form and are silver or silver alloy based. It is typically screen-printed on LTCC green tape, which yields a conductor thickness ranging from a few μm to a few tens of μm . The conductivity of the metallization is usually lower than that of copper, due to the presence of additives incorporated into the conductor paste. This limits the maximum current range to the mA range for optimal performance, but is not regarded as a limitation in this application.

The requirements for the magnetic material for inductors used for RF (if not air core) and power electronics applications differs appreciably, since the effective relative permeability for RF applications is preferably less than 10. For power electronics applications, the required effective relative permeability can range from several tens to several hundreds, depending on the operating frequency. For PCB technology, magnetic sheets compatible with the PCB fabrication process are commercially available. They usually have a low relative permeability range of between 5 and 20, and present a very important limitation to that technology. For thin-film processes, the on-chip inductors are usually air-core for RF applications. For power electronics applications, a wide range of magnetic materials suitable for on-chip inductor integration has been reported [22, 29-32]. They can be sputtered, physically or chemically deposited, and/or electroplated, but are subject to thickness limitations due to the thermo-mechanics. Inductors made using LTCC technology are usually air-core for RF applications in the GHz range. For power electronics applications, LTCC ferrite tapes with a relative permeability range from

several tens to several hundreds are commercially available, making this an attractive alternative to explore for power electronics integration.

In summary, considerations regarding the scalability of the technologies in Table 1-1 for RF to power electronics applications favor an investigation of LTCC for this application. Pending suitable process development, the attributes of LTCC look attractive enough to warrant further exploration.

1.3 Choosing LTCC: Attractive Attributes due to Thermo-mechanical Characteristics

As the operating frequency increases, parasitic inductances and capacitances associated with packaging become a dominant factor affecting the performance of the circuit. For the numerous hybrid packaging techniques reported for high-frequency applications, there is a common interest to integrate the silicon bare die with the hybrid package. This reduces the parasitics caused by the packaging of the silicon die, which tends to shift the operating points of the circuit and adversely affect its performance. In view of this, the thermo-mechanical properties of the hybrid package have to be compatible with that of silicon to ensure acceptable mechanical reliability.

LTCC is a relatively mature technology for RF applications due to its favorable thermo-mechanical properties when integrated with silicon. Table 1-3 compares the thermo-mechanical properties of silicon, LTCC, and PCB.

Table 1-3 Comparison of the Thermo-Mechanical Properties of Silicon, LTCC and PCB

	Silicon	LTCC	PCB
CTE [ppm/°C]	2.6	4 to 8	17
Thermal conductivity [W/m°C]	150	2 to 5	0.3
Specific heat [J/g/°C]	0.7	0.7 to 0.8	0.6

By having a coefficient of thermal expansion close to that of silicon, the reliability of LTCC can be improved, since mechanical stresses which arise due to temperature changes can be reduced. The thermal conductivity of LTCC material is higher than PCB material, but it is still not good enough for effective heat spreading and dissipation. However, effective heat removal can be achieved by using thermal vias or integrating the LTCC with a heat spreader. This therefore indicates that exploring LTCC for power electronics applications opens up an arena that will not only lead to manufacturing low-profile magnetic components, but will eventually lead to a hybrid integration technology for power electronics where a bare die can be included in a LTCC package.

1.4 Choosing LTCC: The Power Magnetics Challenge

In using LTCC for power electronics applications, several aspects have to be considered; namely the suitability of the technology for high current applications, the possibility of producing low profile magnetics, thermal conductivity, ease of heat dissipation, and integrating with heat spreading or dissipating techniques.

1.4.1 Suitability of LTCC for high-current applications

The LTCC processing technique involves screen printing of conductive pastes on the surface of the tapes to form conductive patterns. The cross-sectional area of these printed pastes is determined by the type of screen used; specifically the emulsion thickness, wire mesh size and wire diameter; and the viscosity of the paste. Much research has been done in printing very thin conductive layers with fine pitch on LTCC tape for radio-frequency applications [15]. However, not much work has been done on producing thick conductors suitable for high-current applications. In this dissertation, the processing technique for producing thick conductors in LTCC technology will be developed.

1.4.2 Low-profile Magnetics

In power electronics circuits, magnetic components are usually one of the bulkiest components in the circuit. The increasing market demand for low-profile electronics like ultra-thin notebook computers, flat panel displays, pocket-sized PDAs, iPods, digital cameras, and power adapters provide a strong driving force for the development of low-profile magnetics. In low-profile power electronics applications where high current or high power capability are desired, for instance in notebook computers and flat-panel displays, on-chip integration of magnetics may not be the best option. Hybrid integration of magnetics with the active devices provides another avenue where the requirement for high current and high power can be realized. LTCC technology tailored for low-profile electronics is naturally an area worth exploring for power electronics applications.

1.4.3 Thermal and Mechanical Considerations

The thermal impact of the chosen technology is an important aspect in power electronic circuits. Poor circuit efficiency, degradation of thermal performance due to mechanical or physical aging of materials, repeated thermal cycling of the system when the circuit operating condition changes (e.g. changing from light load to heavy load) can result in poor circuit reliability. Hence, thermal conductivity, ease of heat dissipation, ease of integration with heat spreading or dissipating techniques, and the CTE have to be taken into consideration.

The thermal conductivity of LTCC ceramics ranges from 2 to 5. Although the thermal conductivity is not impressive, it is an order of magnitude better than FR-4¹. The ease of heat dissipation can still be good if heat spreading or dissipating techniques can be applied to LTCC technology. In terms of heat spreading, a high thermal conductivity material, i.e. any electrically conductive material, can be applied to the surface of the ceramic substrate. If an electrically conductive material is not desired, a thermally conductive electrical insulator, e.g. aluminum nitride (AlN) can be used as a heat spreader [41]. In addition, heat dissipating techniques like thermal vias [42] or micro heat pipes [43] can be applied to LTCC technology to alleviate the thermal problem. The other consideration is the coefficient of thermal expansion (CTE). As observed in Table 1-3, the CTE of LTCC is reasonably close to that of semiconductors such as Si and SiC, in contrast to that of PCB material. This gives the prospect of integrating silicon or silicon carbide with LTCC, which in fact has already been realized in the RF arena [44, 45].

¹ FR-4 – an abbreviation for Flame Retardant 4. It is a composite of a resin epoxy reinforced with a woven fiberglass mat, a common material used in printed circuit boards.

In summary, LTCC technology has potential for use in high-current applications. It is a technique for low-profile electronics which has thermo-mechanical properties suitable for integrating with silicon and silicon carbide and is compatible with other heat spreading and heat dissipation techniques. This makes the LTCC technology a prospective candidate for low-profile power magnetics integration.

1.5 Motivation

The increasing market demand for extremely low-profile electronics drives the requirement for low-profile power electronic circuits. Power magnetics is one of the bulkiest components in the circuit, which contributes to the high vertical profile. Hence, there is a strong motivation to look into ways to realize low-profile magnetics, which are easily manufactured. Much work has been done using thick film technology [46, 47] and PCB technology [18, 19] to realize hybrid integrated magnetics for power electronic applications. Using the LTCC technology for high-current power electronics applications is still an unexplored area. In addition, by virtue of the compatible thermo-mechanical properties of LTCC with silicon and silicon carbide, the LTCC technology is a viable solution for integrating with active devices.

1.6 Objectives

This dissertation explores the possibilities of using the LTCC technology as a base integration technology for low-profile power electronics converters. The conventional

LTCC processing will be evaluated and appropriately modified to enable high-current capability. The material obtained from the developed processing will be characterized. The use of LTCC technology for integrable chip inductors is explored and modeled to aid the design of these components. Possibilities of using the LTCC inductor as a substrate for the integrated active part of power converters are also explored in this thesis.

1.7 Organization of Dissertation

Chapter 2 discusses the processing technology for low-profile power magnetics. This chapter is divided into two parts. The first part discusses about the processing issues of sintering the LTCC ferrite itself, and talks about the various problems encountered in sintering thin, intermediate and thick LTCC ferrite samples and solutions are proposed for the various problems encountered.

The second part of Chapter 2 involves assessing the possible metallization for processing the LTCC magnetic component. Since the objective of this work is to explore the possibilities of using LTCC for realizing the planar integration of magnetics, and magnetic components themselves require certain thicknesses to achieve effective magnetic properties, it is necessary to explore the processing issues for a broad range of thicknesses of the magnetic component. Sintering of thin samples and thick samples result in different failure modes. Since copper is an inexpensive metal with excellent electrical conductivity, the possibility of using it with LTCC is studied. Sintering copper with LTCC ferrite tape in different ambient environments is explored, and the effect of the ambient surroundings on the sintering process is discussed. Silver-platinum

metallization is also discussed to finalize the evaluation of the metallization to be used for processing with the LTCC ferrite tape.

Chapter 3 discusses the electrical characterization of the LTCC power magnetics. Permittivity, permeability and core loss measurement are performed for the LTCC magnetic material. Loss measurement often results in large errors, especially in low-loss and low-permeability magnetic materials. Hence, prior to measurement, the sources of error in core loss measurement are identified, and their contributions to the error in power measurement are quantified. The operational influences of biasing, frequency and temperature on core loss are also explored and discussed in the chapter to understand their effects on core loss and to give a realistic view of losses under actual operating conditions and shifts in operating points. Finally, the metallization is characterized to help in the design of the magnetic component.

Chapter 4 discusses the LTCC chip inductor development. Here, the geometry of the inductor is selected. The conventional conductor screen printing technique is evaluated, followed by a study of the influence of the conductor cross-sectional shapes on the electromagnetic losses. This study indicates that screen printing is not well-suited to power electronic applications. A modified inductor fabrication technique is introduced that addresses the requirement for high-current capability as well as for reducing high-frequency losses brought about by the screen-printed conductor paste. The parametric variation of the inductor geometry is studied, and an inductor model is developed, based on the experimental empirical data.

Chapter 5 explores the possibility of using the LTCC inductor as a substrate for hybrid integration with the active power part of the converter. The effect of using the

inductor as a substrate and the consequential increased magnetic coupling in the active circuit is studied. The use of a conductive shield is introduced to alleviate the impact of the magnetic coupling from the inductor substrate on the circuit performance. A simulation study of the conductive shielding is performed to obtain an optimal and practical solution. Samples with and without a conductive shield were constructed for the same physical circuit layout and components. Experimental comparison of circuit behavior of both samples is performed to confirm the possibility of implementing a conductive shield in this technology.

Experimental studies of inductor substrate structures and co-packaged inductors is further carried out for the cases of absence of shield, presence of a grounded shield, and the presence of a floating shield to finalize the evaluation of the hybrid integration technology of designing an inductor substrate for an active power electronics converter.

Chapter 6 concludes the dissertation, which links the process-related issues of the LTCC technology for magnetics integration and the characterization of the LTCC magnetic material to the development of the process for a chip power inductor, the modeling of the chip inductor, and finally to the application of the LTCC magnetic material as a substrate. Further research based on this dissertation will also be discussed.

Chapter 2. Processing Technology for Low Profile Power Magnetics

2.1 Overview of Existing LTCC Processing Technology

The technology for low temperature co-fired ceramics (LTCC) has been developed for numerous applications, varying from RF systems [14, 15, 48] to microfluidic systems with optical detection units [49], pressure sensing [50], and high-power electron multiplier applications [51]. A major advantage of the LTCC technology is the low sintering temperature (< 1000 °C), which allows the use of conductors like Ag, Ag/Pd, Ag/Pt and Au. Furthermore, its coefficient of thermal expansion (4 to 7 ppm/ °C) is close to that of silicon, which makes it suitable for integrating with silicon.

This technology, which was initially developed for military applications, has found its way to the commercial market. For instance, Mitsubishi's WCDMA downconverter uses LTCC to integrate passive components for the interstage filter, hybrid phase shifter and power splitter [52]. The transmit/receive filter and baluns of the Bluetooth receiver implemented by Ericsson are realized on an LTCC substrate [53].

The materials in an LTCC tape comprise glass frit (silicate glass), ceramic filler (alumina), organic binders (plasticizers and anti-flocculant), and the other materials in which the electrical properties are derived, e.g. ferrite in the case of LTCC ferrite tape. LTCC ceramic tapes are prepared by milling precise amounts of raw materials into a homogeneous slurry. The slurry is poured into a Mylar carrier and then passed under a doctor blade to produce a uniform layer of specific thickness. The tape is dried and can

be handled in rolls or sheets. A typical process flow for LTCC multi-layer substrates includes mixing of the component materials, tape casting, preconditioning, tape blanking, registration holes formation, via punching, via filling, screen printing (patterning), stacking, laminating and co-firing. Figure 2-1 shows the process flow of a typical LTCC process starting from the green tape.

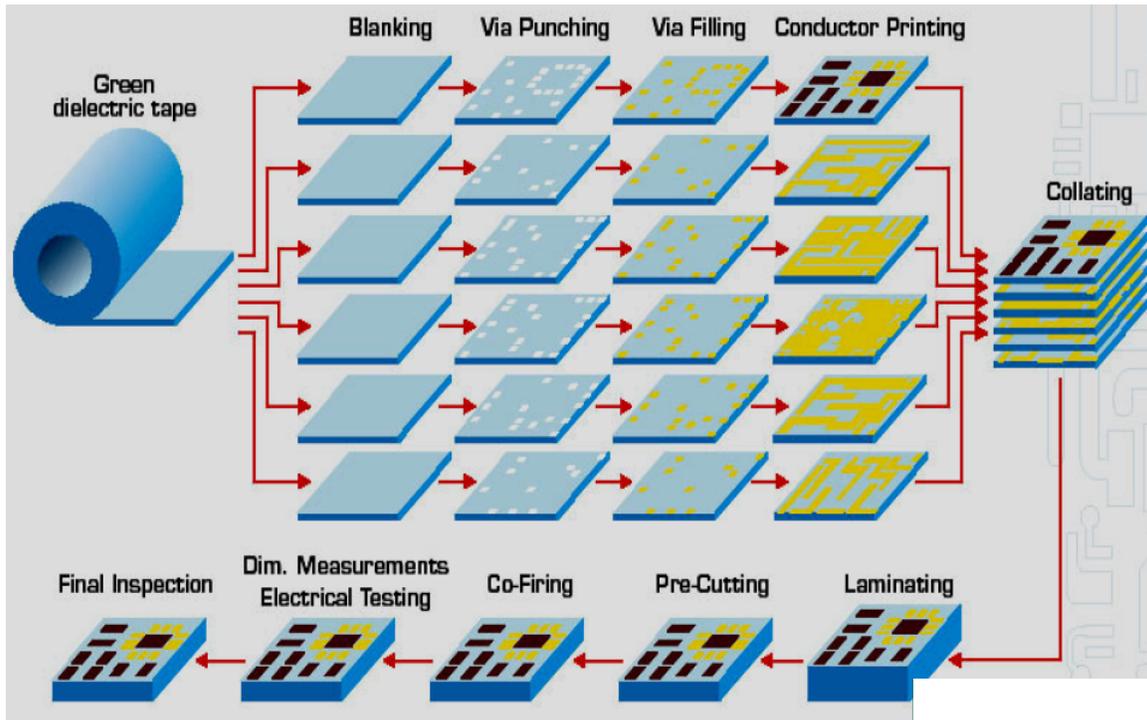


Figure 2-1. Typical LTCC process flow [54].

One of the key limitations of the LTCC technology is the non-uniform shrinkage of the tapes during thermal processing. As a result, localized curvature development [55] during processing can result in delamination [56], cracks [57] and camber [58] in the final product. This affects component assembly, which depends on geometric accuracy

and substrate flatness, as well as the electrical property specifications of the passive components [59].

In order to get around the problem of material mixing and tape casting for small quantities, commercially available tapes were targeted for this study. The LTCC ferrite tape purchased from Electrosience Labs comes in three different permeabilities after sintering; 50, 200 and 500. In this chapter, experiments on the ferrite tape sintering process for inductor fabrication and the choice of metallization are evaluated.

2.2 Thin LTCC ferrite Samples

Several studies have shown that curvature or camber after sintering is due to the mismatched sintering kinetics between the substrate and overlying conductor paste patterns [58, 60, 61]. Inhomogeneities in the tape itself due to casting [55] or induced during lamination [55] can contribute to camber. In this section, thin layers of the LTCC ferrite tape are sintered and evaluated. The solution of applying a constant weight prior to sintering is proposed as a means to avoid warping of thin samples in small batches. An alumina powder layer can be used to prevent cracking at the edges of the thin LTCC sample due to the friction and constraints imposed by the alumina tiles, which are used to sandwich the sample prior to sintering.

2.2.1 Warping of Thin Samples

As a start, the ferrite tape was cut into 1 cm x 1 cm squares and sintered in air using the sintering profile shown in Fig. 2-2, as recommended by Electrosience Labs [62].

The thickness of the green tape is $70 \mu\text{m} \pm 5 \mu\text{m}$ according to the datasheet. The tapes were checked under the microscope to be free of pinholes. The single layer samples were placed on an alumina setter tile prior to sintering. Figure 2-3 shows the samples before and after sintering. Radial warping of all the samples were observed after sintering and the samples were observed to shrink by around 20% [62] in each direction after sintering. The warping of the samples after sintering could be due to particle sedimentation during casting and/or drying [63]. This causes the upper part of the single-layer tape to contain smaller particles than the bottom part of the tape. During sintering, the upper part of the layer is likely to shrink more quickly compared with the bottom part of the layer. This causes the upward warping of the samples. As the liquid phase ‘nucleates’ and exert capillary forces on the particle bed [55], microslumping of the samples occurs, which is characterized by the gravity-driven downward motion of the ends of the tape.

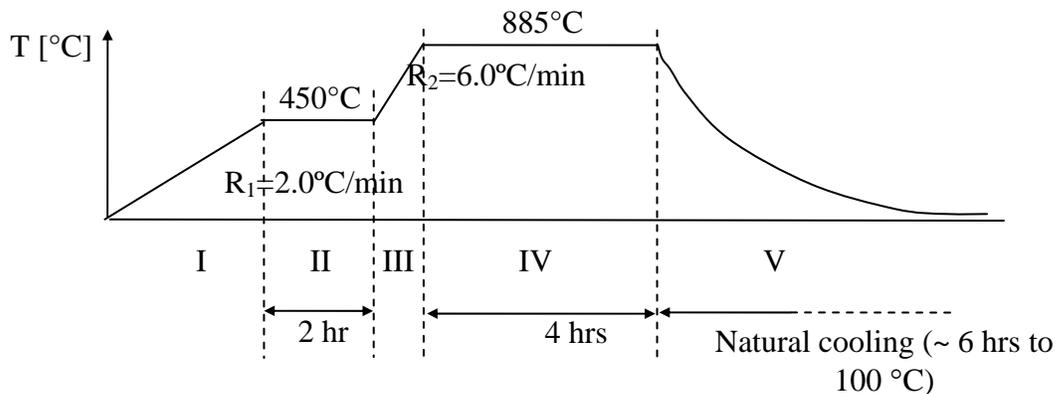


Figure 2-2. Sintering profile for LTCC samples.

Figure 2-3 shows the single layer LTCC ferrite tapes before and after sintering without applying weight during sintering. The darker circle in the middle of the sintered sample is an indentation. The lighter color around it is the ridge. The localized curvature in the casting direction is always larger regardless of the green state curvature [55].

Measurement of the difference in curvature is difficult for the samples in Fig. 2-3 due to the large degree of radial warping and the microscopic difference in curvature due to casting direction.

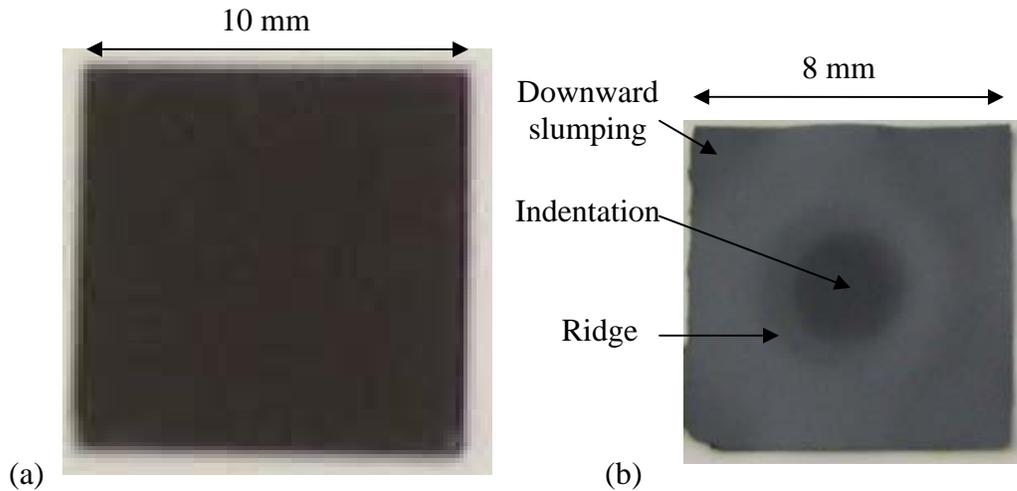


Figure 2-3 Single layer LTCC ferrite tapes (a) before and (b) after sintering, without applying weight during sintering.

2.2.2 Weight Application during Sintering for Thin Samples

To get around the problem of the warping of thin samples, a constant weight was applied to the sample during sintering. Three samples, one with a single layer, one with two laminated layers, and one with four laminated layers of ferrite tape with dimensions 1 cm x 1 cm were prepared. The two-layer and four-layer samples were laminated at a pressure of 10 MPa (1500 psi) at a temperature of 70°C to give a total thickness of $135 \pm 5 \mu\text{m}$ and $270 \pm 10 \mu\text{m}$. A piece of alumina tile is placed over the samples prior to sintering to prevent warping. Figure 2-4 shows three samples; the single layer, the two laminated layers, and the four laminated layers of ferrite tape after sintering, with weight applied during sintering. No warping of the samples was observed.

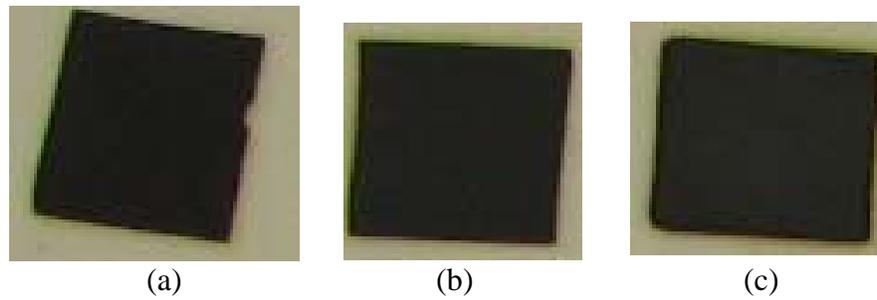


Figure 2-4 LTCC ferrite tape with dimensions of 8 mm x 8 mm after sintering, applying weight during sintering. (a) Single layer, (b) two laminated layers and (c) four laminated layers.

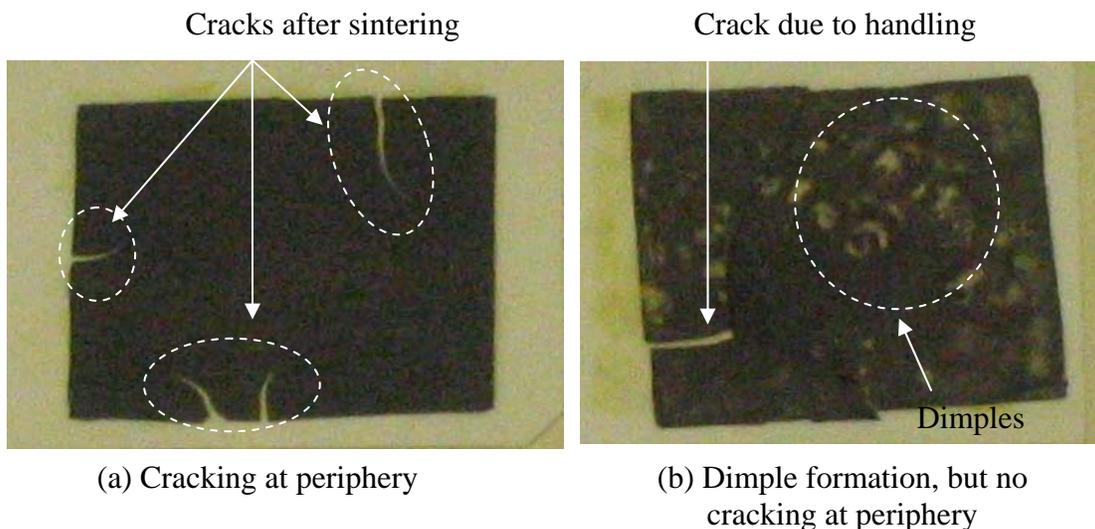
In summary, application of weight to thin LTCC ferrite tape samples prior to sintering prevents warping of the samples.

2.2.3 Application of Alumina powder

Being able to make a mechanically defect-free material is an essential step in minimizing the complications that may arise from these defects in the material. The ability to sinter a crack- and dimple-free LTCC material was essential for the more complex processing which follows. In this set of experiments, a 5.2 cm x 4 cm two-layered laminated ferrite tape was sintered in air. Another was sintered between alumina tiles without applying powder on the tiles or on the sample, and two more were sintered with alumina powder applied on the bottom tile where the sample was placed and on the upper surface of the sample. For one of the two samples with alumina powder applied, a non-uniform layer of alumina powder was sprinkled onto the alumina tile prior to placing the sample onto the tile. For the other sample, a thin layer of powder was applied on the alumina tile using a blade. The samples were 4.2 cm x 3.2 cm after sintering.

Cracking of the sintered tape was observed, as shown in Fig. 2-5(a), which is suspected to be due to the downward pressure from the Al_2O_3 tile used to sandwich the thin sample. Al_2O_3 powder was used to alleviate the constraint problem to allow shrinkage movement of the tape under elevated temperatures. When a non-uniform layer of Al_2O_3 powder was applied, dimple formation was observed, as in Fig. 2-5(b), which is due to the unevenness of the powder applied. However, there was no cracking at the periphery due to sintering. Finally, when a thin and uniform layer of Al_2O_3 powder was applied, there was no cracking nor dimple formation, as shown in Fig. 2-5(c).

In summary, there was cracking at the edges of the thin LTCC sample due to the friction and constraints imposed by the alumina tiles used to sandwich the sample prior to sintering. Application of a layer of alumina powder between the sample and the alumina tiles alleviates this problem. Applying an uneven layer of alumina powder results in dimpling, which can be avoided by applying a thin and uniform layer of alumina powder on the samples prior to sintering.





(c) No cracking and no dimple formation

Figure 2-5 Two-layered laminated ferrite tape samples after sintering. (a) Sample sintered between alumina tiles without applying powder on the tiles or sample, (b) sample with a non-uniform layer of alumina powder applied, (c) sample with a thin layer of alumina powder applied.

2.3 Thick LTCC Ferrite Samples

It has been reported that the curvature of sintered green tape is always larger in the casting direction, regardless of the green state curvature [55]. To minimize the impact of casting direction on the camber of the samples, the tapes for the samples are stacked such that each layer is rotated 90° with respect to the layer below. The tapes are laminated at the recommended temperature of 70°C and at the recommended pressure of 10 MPa (1500 psi) [62]. In this section, the problems of sintering thicker samples are examined. Solutions to sintering samples of intermediate thickness and thick samples are proposed.

2.3.1 Circumferential cracking of thick samples

Four layers of ferrite tape (25 mm x 25 mm) are laminated at a pressure of 10 MPa (1500 psi) at a temperature of 70°C . Figure 2-6 shows a (a) four-layered sample and (b)

eight layered sample after sintering, with weight applied during sintering. Sample (a) has alumina powder applied and sample (b) does not have alumina powder applied to the sample prior to sintering. It is observed that both samples have the tendency to fracture into a circular section during sintering regardless of whether alumina powder is applied.

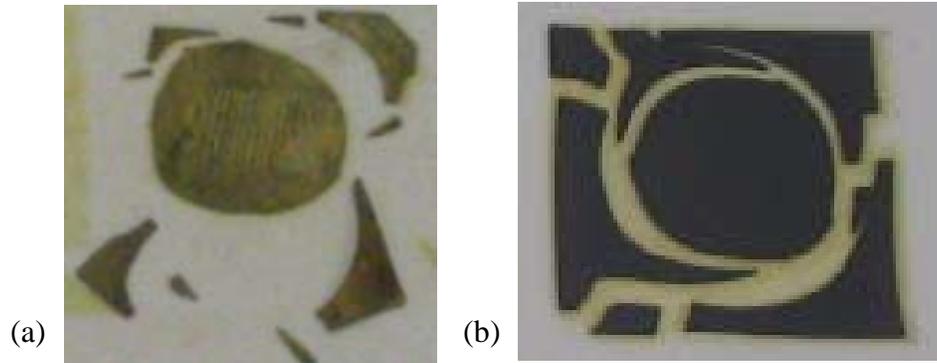


Figure 2-6 LTCC ferrite tape after sintering, when weight was applied during sintering. Sample (a) comprises four layers of laminated LTCC tape and has alumina powder applied. Sample (b) comprises eight layers of laminated LTCC tape and does not have alumina powder applied to the sample.

From this, it can be concluded that application of alumina powder for thin samples can prevent cracking at the edges of the sample, which is attributed to frictional constraints imposed by the alumina tiles used to sandwich the sample. Application of alumina powder for a sample with intermediate thickness, where there are four to eight layers, or a thick sample of more than eight layers, does not prevent the cracking problem.

2.3.2 Are circular samples the solution to avoid circumferential cracking?

In this section, circular samples of various thicknesses are fabricated to explore if it is a solution to avoid circumferential cracking. For magnetic components, there is a

requirement for sufficient core volume for magnetic energy storage. In view of this requirement, it is necessary to explore the processing aspect for fabricating thick ferrite samples. Three circular samples with 4 layers, 10 layers and 20 layers of ferrite tape are fabricated as shown in Fig. 2-7. The samples have a diameter of 20 mm. No cracking is observed for the 4-layer and the 10-layer samples. Some circumferential cracking of the sample is observed for the 20 layer sample. For the 20-layer sample, a higher laser power is used to cut the sample into a circle. Partial sintering of the peripheral might have caused the circumferential peeling, as observed in Fig. 2-7(c).

It is of interest to see whether circular samples and samples without sharp edges are the solution to prevent circumferential cracking for samples with embedded conductor. Two single conductor inductors are fabricated; a straight conductor inductor, and an inductor with U-shaped conductor. Twenty layers of ferrite tapes are used for each sample. Figure 2-8 shows the fabrication procedure of the inductors. The inductor with the U-shaped conductor is laser cut into a circle. The inductors with the straight conductor and the U-shaped conductor are sintered with three pieces of alumina tiles on top to act as weight.

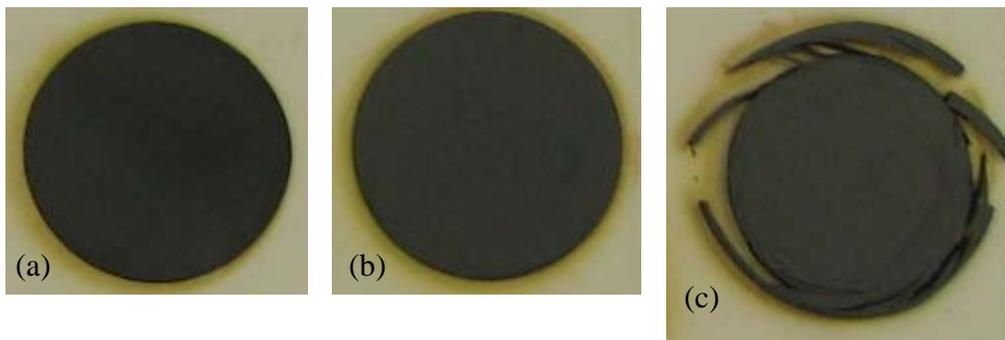


Figure 2-7. Circular samples of diameter 20 mm with (a) 4 layers, (b) 10 layers and (c) 20 layers of ferrite tape. Weight is applied during sintering.

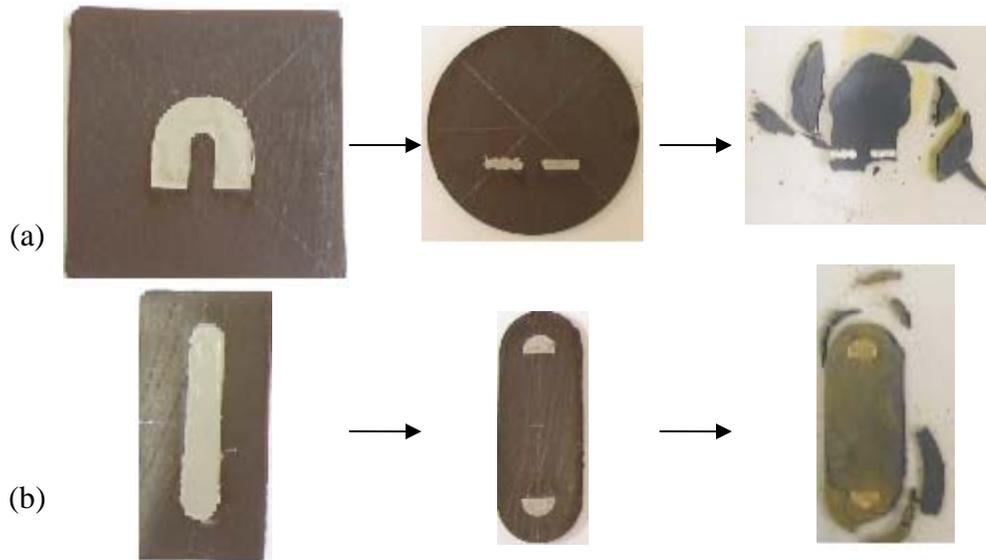


Figure 2-8 Fabrication procedure of 20-layered samples of LTCC ferrite tape with embedded conductor patterns. (a) Circular sample with U-shaped conductor, (b) capsule-shaped sample with straight conductor applying weight (3 pieces of alumina tile) during sintering.

It is observed that severe cracking of the 20-layered samples occurred for the circular sample with embedded conductor, as in Fig. 2-8(a), compared to that without an embedded conductor (see Fig. 2-7(c)). This suggests that gases from the silver paste exacerbate the cracking problem. This shows that cutting the sample into a circle is not the best solution for preventing circumferential cracking of thick samples, especially when conductors are embedded. In addition, fracturing of the samples is observed to occur at 350-400 °C, before the binder burnout stage. This suggests that the cracking is probably due to the forced escape of the gaseous by-products which is inhibited by the applied weights on top. In addition, the gases from the Ag/Pt paste also contribute to cracking of the LTCC sample. In the effort to see if elongated samples are possible, a capsule-shaped sample with rounded corners is fabricated. For the capsule shaped sample, as shown in Fig. 2-8(b), cracking is also observed.

From the above experiments, we've learned that for thinner samples in which weight must be applied during sintering, cutting the sample into a circle can help in reducing the chance of circumferential cracking of the sample. Thicker samples will crack even when the sample is cut into a circle. The cracking is more severe when a conductor is embedded. Cracking is due to forced escape of gases before binder burnout, which is inhibited by the applied weights.

2.3.3 Sintering thick samples

Twenty-layer samples are made into capsule and circular shapes with straight conductors embedded in the magnetic structure. Figure 2-9 shows the fabrication procedure of the single-conductor inductors laser-cut into capsule and circular shapes. The inductors were sintered without any applied weight on top.

It is observed that none of the samples suffer any cracking or fracturing. This shows that sintering has to be performed with the top uncovered to allow gases to escape when the temperature is elevated. In addition, the samples conform to the setter tile if the tile is thick. Figure 2-10 shows a 20-layered rectangular sample with an embedded conductor before and after sintering.

In summary, the sintering of thin samples require weight to be applied prior during sintering to prevent warping of the sample. When the sample is of intermediate thickness, between four and ten layers, cutting the sample into a circle can prevent circumferential cracking of the sample. For thick samples of more than ten layers, weight applied prior to sintering can result in fracturing of the sample. Since thick samples conform to the setter tile during sintering, the samples can be sintered without applying

any weight prior to sintering. The first ramp rate (section I in Fig. 2-2) can be lowered to 0.5 °C/min to slow down the escape of gases before the binder burnout process.

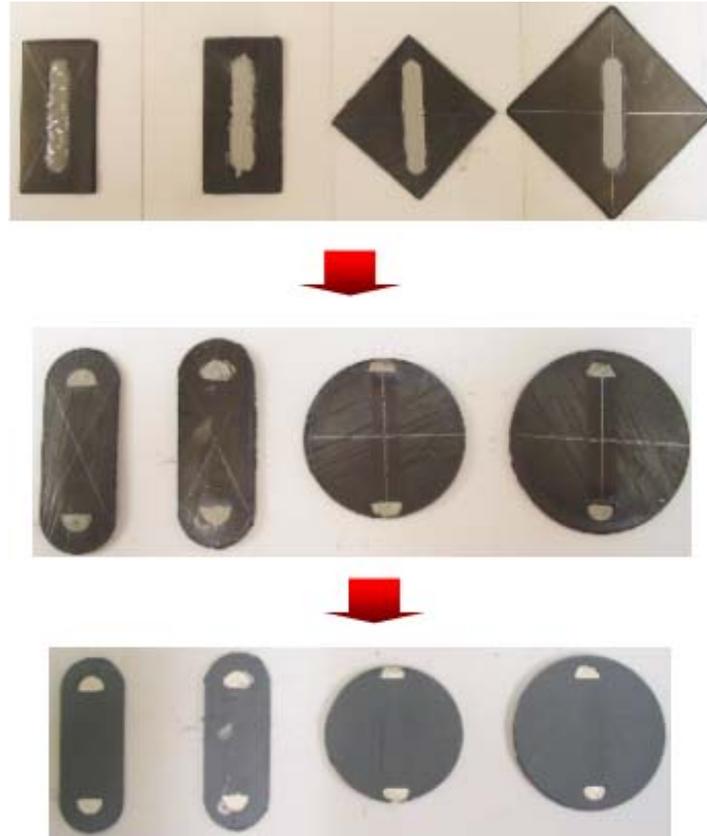


Figure 2-9 Fabrication procedure of single-conductor inductors without applying weight during sintering.

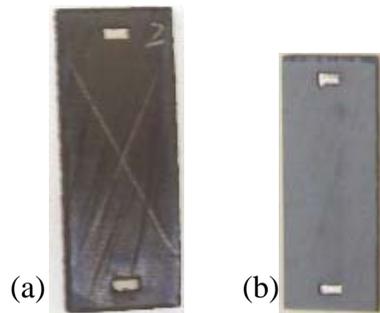


Figure 2-10 Twenty-layered rectangular samples of LTCC ferrite tape with embedded conductor (a) before and (b) after sintering.

2.4 Choice of Metallization

The power applications of the end product require an electrical conductivity as high as possible (which means conduction losses as low as possible) of the metallization. The choice of the metallization technology for the LTCC process affects the conductivity of the conductor as well as the cost. However, since the LTCC processing involves extremely high temperatures, the choice of metal type becomes limited. Copper, an inexpensive metal with the highest electrical conductivity, is one of the best candidates. However, since it oxidizes at elevated temperatures, it may not be the best choice to be used with LTCC. In this section, the possibility of using copper with LTCC will be evaluated.

2.4.1 Possibility of Using Copper with LTCC

In this section, samples are sintered at various ambients to observe their effect on sintering. The three sintering ambients used are: (a) oxidizing ambient (air), (b) reducing ambient (H_2/N_2), and (c) inert ambient (Ar). Three samples are made, which comprise a strip of copper sandwiched between two layers of ferrite tape and laminated at a pressure of 10 MPa (1500 psi) and at a temperature of 70 °C. Figure 2-11 shows a drawing of the samples. Figure 2-12 shows the samples sintered in the three ambients.

The copper in the sample sintered in air has been oxidized, as seen in Fig. 2-12 (a). For the samples sintered in the reducing ambient, the copper remains un-oxidized, but reduction of the ferrite into metallic iron is observed, as shown in Fig. 2-12(b). The sample becomes silver in color and shows conductive behavior when tested with a

multimeter. For the sample fired in an inert ambient, as in Fig. 2-12(c), the copper remains in tact, but the ferrite tape is observed to be black, as opposed to becoming gray, which is characteristic of ferrite, after sintering.

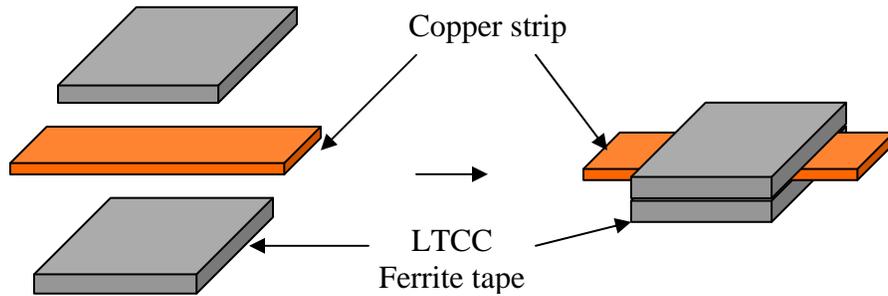


Figure 2-11 Drawing of sample with copper strip sandwiched between two layers of ferrite tape.

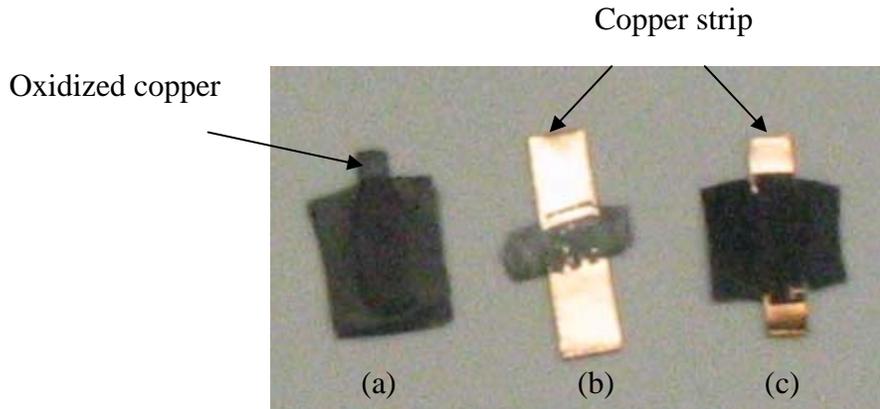


Figure 2-12 Samples of copper strip sandwiched in two layers of ferrite tape fired under (a) oxidizing (air) ambient, (b) reducing ambient (H_2/N_2) and (c) inert ambient (Ar).

To investigate the effect of sintering ambient on the ferrite tape itself, another three samples are fabricated. The samples are square toroids. Eight layers of ferrite tape are laminated at a pressure of 10 MPa (1500 psi) and at a temperature of 70 °C. The samples are cut into 10 mm x 10 mm squares with a 5 mm x 5 mm square hole in the middle.

These samples are sintered in (a) oxidizing ambient (air), (b) reducing ambient (H_2/N_2) and (c) inert ambient (Ar) to observe the effect of sintering ambient on the LTCC ferrite samples. The samples sintered under the three ambients are shown in Fig. 2-13.

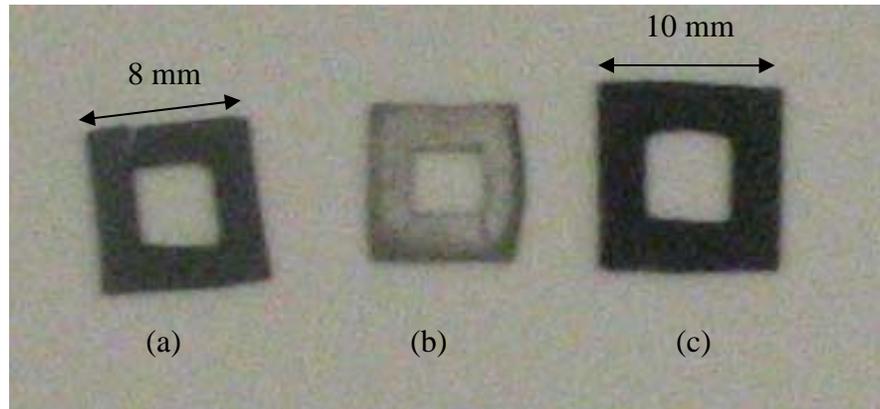


Figure 2-13 Square toroid samples fired under (a) oxidizing (air) ambient, (b) reducing ambient (H_2/N_2) and (c) inert ambient (Ar).

The sample sintered in air is dark gray, which is characteristic of ferrite; as seen in Fig. 2-13 (a). The sample is also observed to have shrunk by 20 % in each dimension. For the sample sintered in a reducing ambient, the ferrite is reduced into metallic iron as observed in both Fig. 2-12(b) and 2-13(b). The sample becomes silver in color and shows conductive behavior when tested with a multimeter. For the sample fired in the inert ambient, shown in Fig. 2-13(c), the ferrite tape sample is observed to be black, and there is no observable shrinkage of the sample after firing.

In summary, in order for a complete organic burnout to take place, sintering in an oxidizing ambient is necessary, but it causes copper to oxidize. To prevent copper from oxidizing, sintering in a reducing ambient is performed. However, this causes the ferrite to reduce into metallic iron, which makes it a conductive magnetic material, which is undesirable in terms of power loss. Sintering in an inert ambient to prevent copper

oxidation also proves to be unsatisfactory as this prevents the organic binder burnout process due to the lack of oxygen, though copper oxidation is avoided.

2.4.2 Reduction of copper oxide to copper

A possible solution to counteract the copper oxidation problem is to first conduct the sintering in air to allow organic burnout to take place. After the sintering step, copper oxide can be reduced back to copper in a reducing ambient, at a lower temperature to slow down the process of ferrite reduction.

A strip of copper laminated with ferrite tape on both sides was sintered in air at 885 °C. After cooling down to room temperature, the samples were then placed in a reducing ambient, H_2/N_2 , and the temperature raised to 350 °C for one hour. Figure 2-14 shows the sintering profile, consisting of the organic burnout, densification and reducing step.

A cross-sectional view of the copper after oxidation and reduction is studied and compared. Figure 2-15 shows the cross-sectional view of copper (a) before oxidation, (b) after oxidation, and (c) followed by subsequent reduction.

From Fig. 2-15(b), it is observed that after the copper is oxidized, it increases in volume. This causes the ferrite tape surrounding the copper to be under tensile stress. Cracking and delamination of the ferrite tape at the edges of the copper may result, as shown in Fig. 2-15(b). It is also observed that after copper oxide is reduced back to copper it does not shrink back to its original volume. This suggests an increased in overall porosity of the copper after reduction and a possible reduction in the conductivity of copper, which underwent a redox reaction.

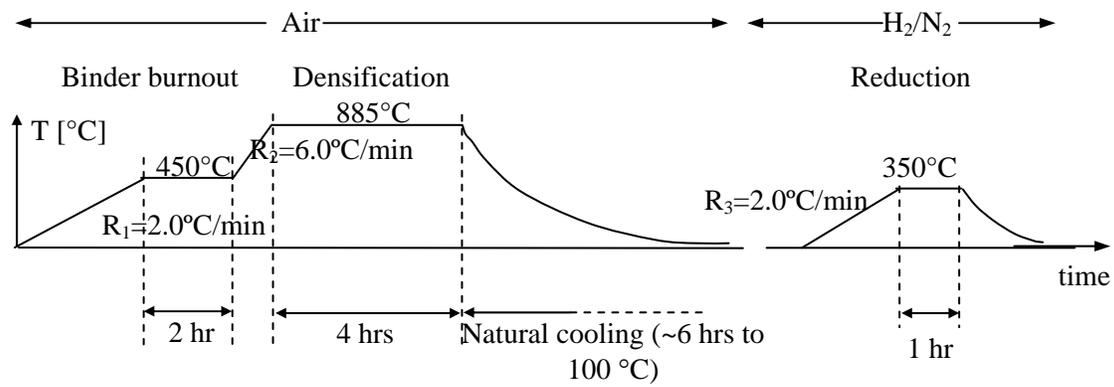
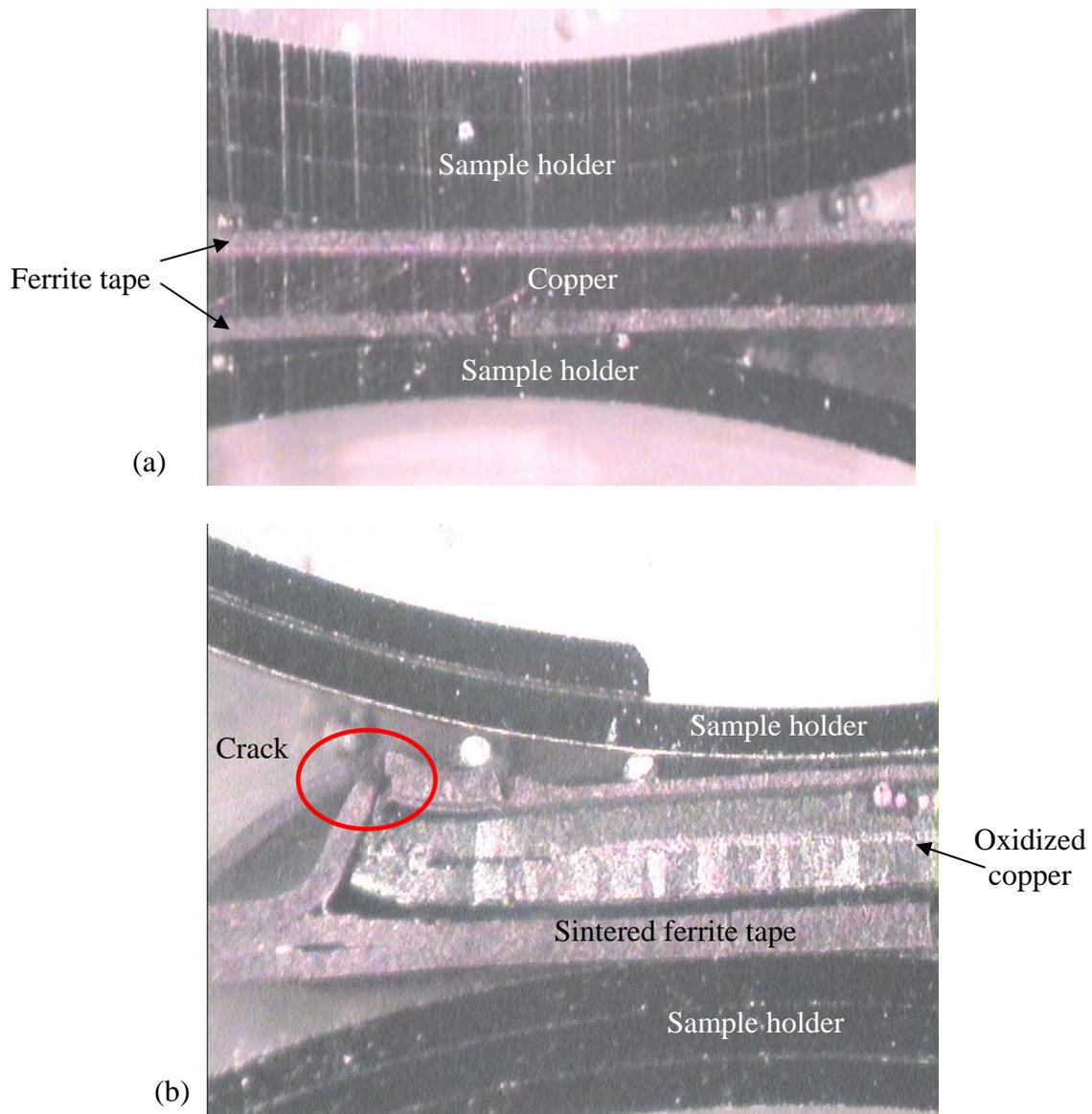


Figure 2-14 Sintering profile conducted in air followed by reducing profile conducted in H₂/N₂.



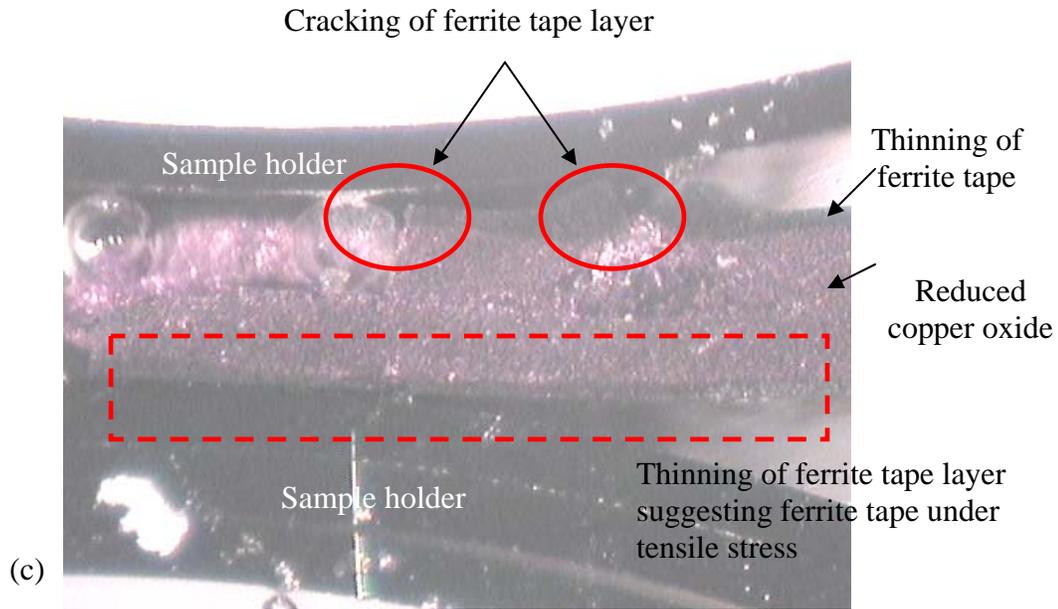


Figure 2-15 Cross-sectional view of copper (a) before oxidation, (b) after oxidation, (c) followed by reduction.

In summary, severe volume expansion of copper occurs after redox reaction. A large volume expansion of oxidized copper after sintering introduces additional stress on the system, since ferrite tape, which surrounds the conductor, shrinks upon sintering and copper expands after the process. Hence, it can be concluded that it may not be feasible to use metallic copper in our co-firing process with ferrite tape.

2.4.3 Sintering LTCC tape with sandwiched alumina strips

A possible solution to avoid the copper oxidation problem is to sandwich thin alumina strips between ferrite tapes and remove them after sintering to replace with copper strips. 2" x 2" alumina tiles with thickness of 125 μm are obtained as samples from Accumet [64].

The tile is cut into strips 500 μm wide and laminated between LTCC tape with two layers of tape each on the top and bottom. The sample is sandwiched between two pieces

of silicone rubber pads during laminating to improve the distribution of pressure on the sample, since the surface of the sample is uneven due to the presence of the alumina strip. The samples with sandwiched alumina strips are sintered in air with the sintering profile shown in Fig. 2-2. Figure 2-16 (a) shows the samples before sintering, and Fig. 2-16 (b) shows the samples after sintering. Figure 2-17 shows the cross-sectional view of a post-sintered sample with the alumina strip sandwiched between layers of ferrite tape.

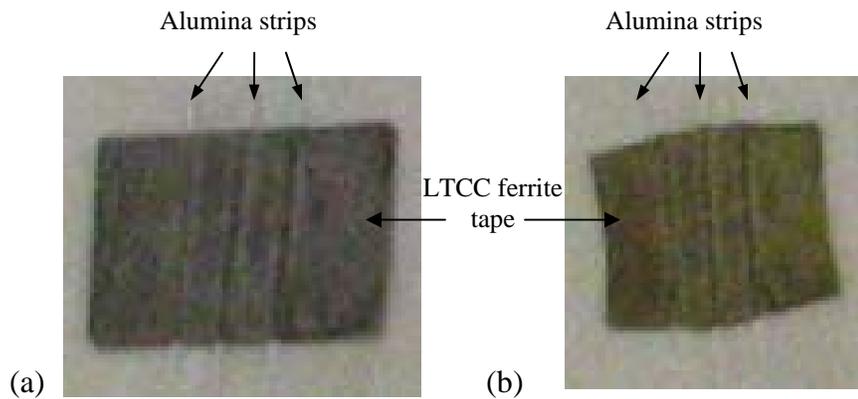


Figure 2-16 Thin alumina strips sandwiched in LTCC ferrite tape (a) before and (b) after sintering.

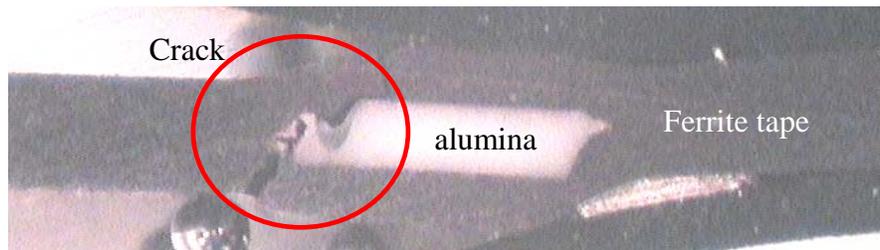


Figure 2-17 Cross-sectional view of a thin alumina strip sandwiched in LTCC ferrite tape after sintering.

In Fig. 2-16 (b) fracturing of the LTCC tape at the edges parallel to the alumina strips is observed, which is due to constrained shrinkage of the LTCC tape. The alumina strips are observed to adhere strongly to the sintered tape. In Fig. 2-17, fracturing of the LTCC tape at the edges is observed under a microscope. This is attributed to stresses developed during sintering, when the LTCC tape shrinks and the alumina strip does not change in

volume. Hence, sandwiching thin alumina strips between ferrite tapes and removing them after sintering to replace with copper strips may not be feasible.

2.4.4 Using Copper Paste

Copper paste designed for thick-film printing can be purchased from Electroscience Labs. The recommended firing temperature is 900 °C to 980 °C in a nitrogen sintering ambient, with optimum performance achievable by firing at 980 °C. However, this temperature is 100 °C higher than the recommended sintering temperature of the LTCC ferrite tape. In addition, the resistivity of the copper after sintering is less than half that of elemental copper due to the presence of additives and glass included in the paste. Figure 2-18 shows the sheet resistance of such printed copper paste vs. fired thickness [65]. The conductivity of the sintered copper paste ranges from 25 to 34 MS/m, which is around half the conductivity of elemental copper.

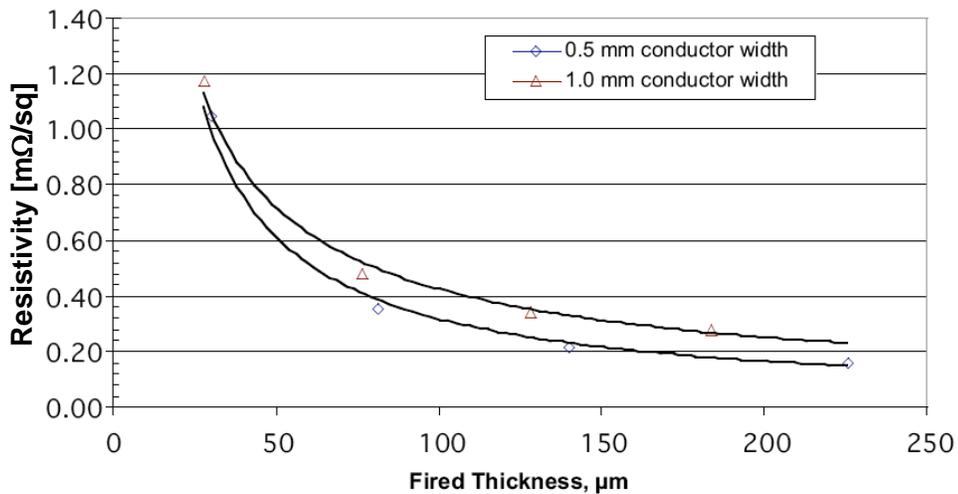


Figure 2-18 Sheet resistance of sintered copper paste vs. fired thickness [65].

Due to the complexity in the sintering process of copper paste, which requires sintering in an inert ambient, as well as the difference in sintering temperature between the copper paste and the LTCC ferrite tape, we must seek other options in the choice of metallization.

2.4.5 Using Ag/Pt Paste

In section 2.4.2 it is concluded that the volume expansion of copper after sintering resulted in severe tensile stress in the ferrite tape, which shrinks after sintering. This difference in sintering behavior makes copper a less compatible conductor with the LTCC processing technique. In this section, experiments using Ag/Pt paste conductors purchased from Electrosience Labs with the LTCC ferrite tape are reported. The Ag/Pt paste has a recommended sintering temperature of 875 °C [66], which is very close to that of LTCC ferrite tape (885 °C), which can ensure co-firing compatibility with the LTCC ferrite tape.

To test the compatibility of the Ag/Pt paste with LTCC ferrite tape, the conductor paste is screen-printed onto a layer of LTCC ferrite tape. The conductor is dried at 70 °C for one hour. Two layers of LTCC ferrite tape are placed on top and one layer is placed on the bottom of the LTCC ferrite tape sample with a printed conductor pattern. The sample is laminated at 70 °C at a pressure of 10 MPa (1500 psi), forming a structure with embedded conductors. The sample is sintered using the sintering profile in Fig. 2-2. Figure 2-19 shows the cross-sectional view of the sample after sintering. No sign of cracking is observed, as opposed to the cracking and thinning of ferrite tape observed when copper is used as the metallization, as shown in Fig. 2-15(c).

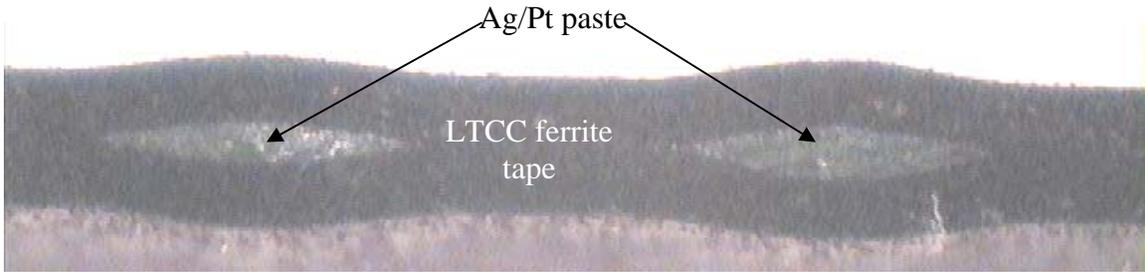


Figure 2-19 Cross-sectional view of screen-printed Ag/Pt conductors embedded in LTCC tape after sintering.

In terms of processing, the ESL 953 Ag/Pt paste is compatible to process with the LTCC ferrite tape, since their recommended co-firing temperatures are very close to each other. Experimental results of co-firing the Ag/Pt paste with LTCC ferrite tape shows no signs of cracking, delamination or thinning of the LTCC tapes.

2.4.6 Alternative cross-sectional shapes for conductors

In the development of a fabrication process suitable for power applications, several essential points must be taken into account, such as the choice of magnetic material for the targeted application, flexibility in the design, and manufacturing of an inductor with low conduction losses. The conventional method of screen-printing conductor paste on LTCC green tape proves to be unsuitable for power applications due to the limitation in the conductor's cross-sectional area and cross-sectional shape [67], as illustrated in Fig. 2-19. The presence of sharp edges would lead to high current densities at these edges, which will result in elevated conduction losses. The situation is aggravated when the conductors are embedded in a magnetic medium. The next section elaborates on the

LTCC power inductor fabrication procedure to form conductors with better-shaped and larger cross-sectional area.

2.4.7 Power Inductor Fabrication Procedure

2.4.7.1 Single Conductor Inductor

The materials used for inductor fabrication are LTCC ferrite green tape² and silver/platinum (Ag/Pt) paste³ purchased from Electrosience Labs [28]. First, the LTCC ferrite tapes are cut into rectangles. Several layers of the rectangular LTCC ferrite tapes are laminated to form the top, middle, and bottom main layers. The tapes are laminated using a hydraulic lab press. The laminating temperature is 70 °C and the pressure is 10 MPa (1500 psi). A slot is cut in the middle main layer using a Class IV 100 W CO₂ laser cutting machine. Two smaller slots 21 mm apart are laser-cut in the top main layer. Figures 2-20(a) and 2-20(b) are photographs of the bottom and middle main layers after the laser cutting step.

The main middle layer is placed on top of the bottom main layer and subsequently laminated at a temperature of 70° C, with a pressure of 10 MPa (1500 psi), as shown in Fig. 2-20(c). Next, Kapton tape is adhered to the structure, and the part of the Kapton tape that lies above the indented slot is removed using an X-acto knife, exposing the slot. Ag/Pt conductor paste is then wiped into the slot using a 6 cm × 4 cm × 0.6 cm silicone rubber squeegee. The Kapton tape layer serves to protect the underlying LTCC ferrite

² LTCC ferrite green tape – part number ESL-40010

³ Ag/Pt paste – part number ESL-953

structure from the conductor paste. Figure 2-20(d) shows a photograph of the structure with Ag/Pt paste dispensed into the slot.

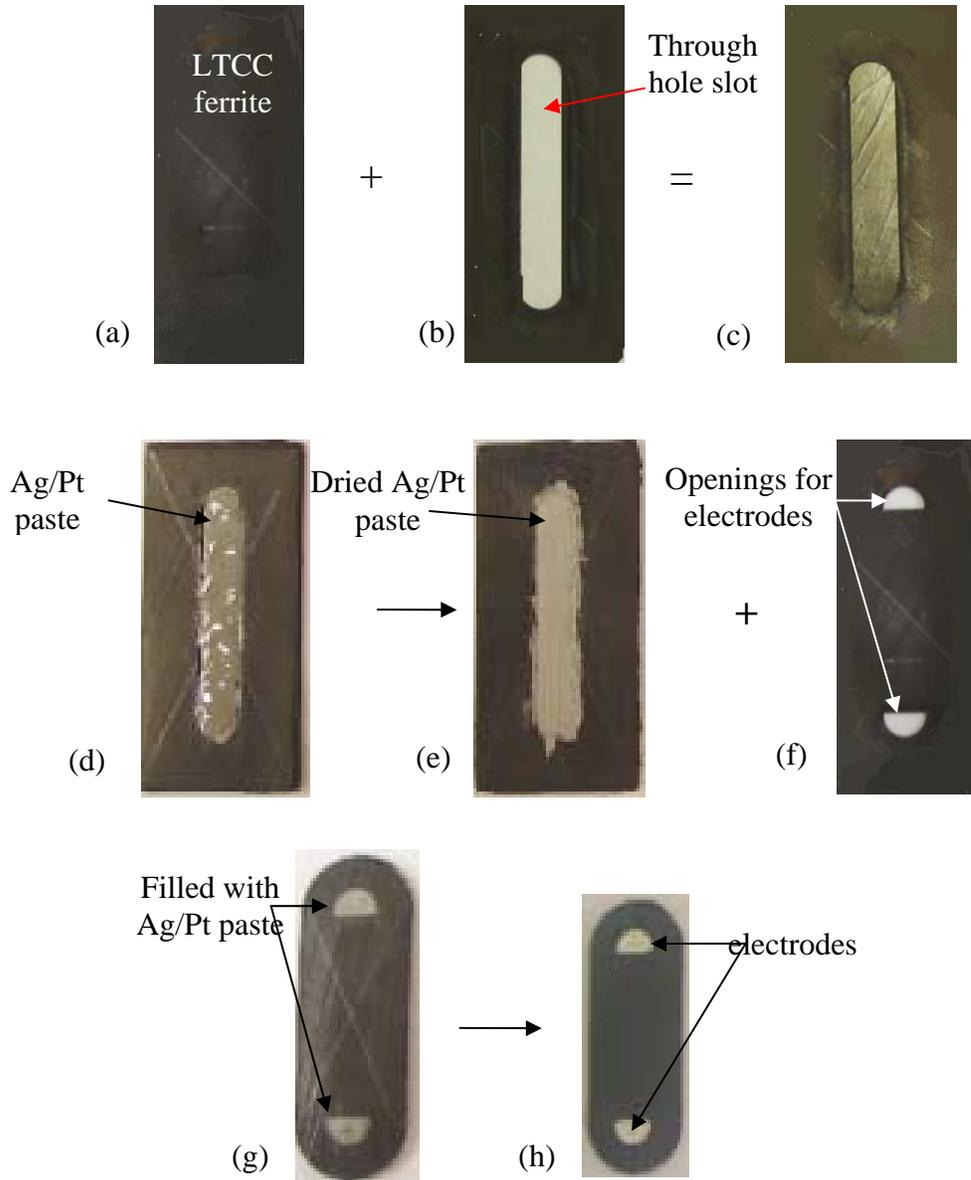


Figure 2-20 LTCC inductor fabrication procedure. (a) Bottom Layer, (b) middle layer, (c) laminate bottom and middle layers, (d) Fill slot with conductor paste, (e) dry conductor paste at 80 °C, laminate (e) with top layer (f), (g) Fill slots with conductor paste and laser cut into desired shape, (h) inductor after sintering.

The structure is then placed on a hot plate of temperature 80° C to drive off solvents and dry the conductor paste. After the solvents are driven off, the dried conductor

decreases in volume, resulting in vertical shrinkage. The process of wiping the conductor paste into the slot is then repeated four to five times until the dried conductor paste is almost level with the ferrite layers at its peripherals. Then the Kapton tape is removed. Figure 2-20(e) shows the structure after the conductor dries.

Next, the top main layer, shown in Fig. 2-20(f), is laminated on top of the structure shown in Fig. 2-20(e). Conductor paste is then dispensed into the two small slots, which will form the pads for the electrodes for external connection. It is then laser-cut into the desired size and shape, as shown in Fig. 2-20(g). The structure is then sintered in a normal atmosphere using the VULCAN 3-550 sintering oven, as per Fig. 2-21. A photograph of the fabricated inductor is shown in Fig. 2-20(h). Due to the large thickness of the LTCC tape layers and the conductor paste, the first ramp rate of the sintering profile from room temperature to the binder burnout temperature is lowered to 0.5 °C/min.

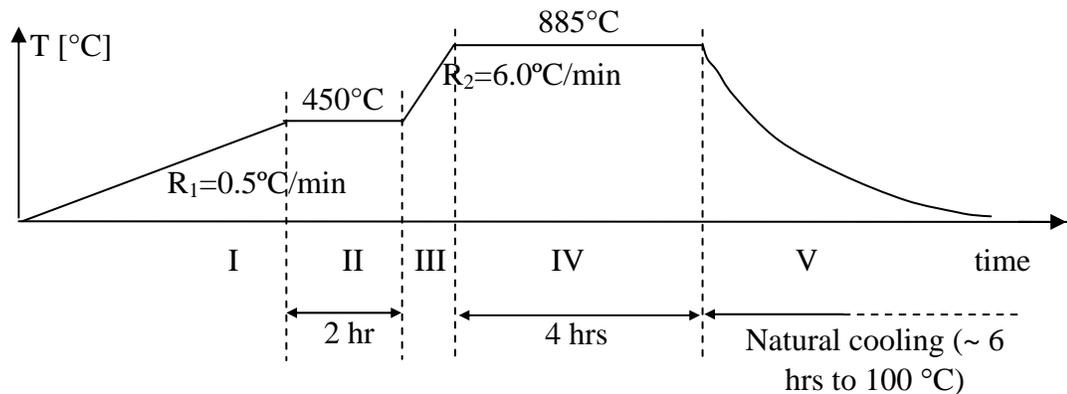
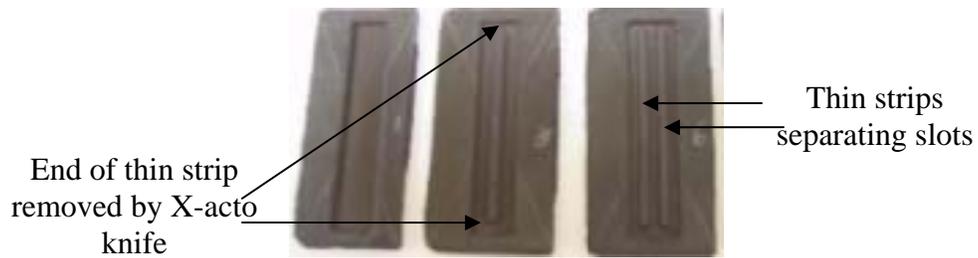


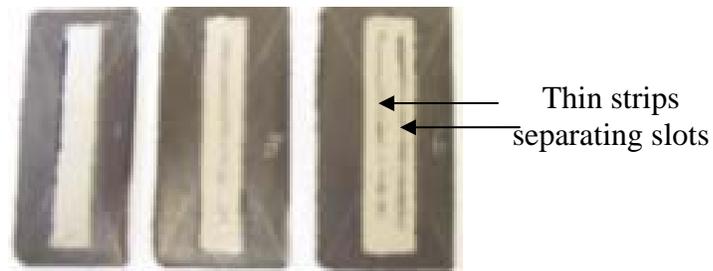
Figure 2-21 Sintering profile for LTCC inductor samples with reduced 1st ramp rate (region I).

2.4.7.2 Multi-Conductor Inductor

The fabrication of the multi-conductor inductor is similar to that of the single conductor inductor. For the middle main layer, the respective number of slots is cut, as similar to the step shown in Fig. 2-20(b). The middle main layer is then laminated with the bottom main layer. The ends of the thin strips which separate the individual slots are removed using an X-acto knife, as illustrated in Fig. 2-22 (a). Subsequently, conductive paste is dispensed into the slots and dried at 80 °C to drive off solvents. The procedure of dispensing conductive paste is repeated four to five times, similar to that of the single conductor inductor. Figure 2-22(b) shows the samples with slots filled with dried conductive paste.



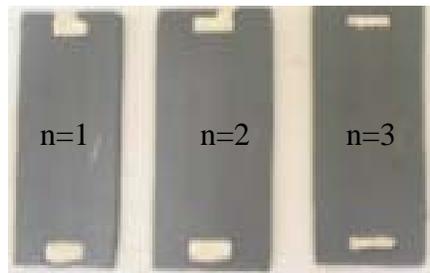
(a) Formation of indented slots.



(b) Dispensing of conductor paste.



(c) Laminating top layer, exposing inductor electrodes.



(d) After sintering.

Figure 2-22 Fabrication procedure for multi-conductor inductor with number of parallel conductors, $n = 1$ to 3.

Next the top main layers are laminated with the structures shown in Fig. 2-22(b), resulting in Fig. 2-22(c). Conductor paste is then dispensed into the exposed slots, which form the pads for the electrodes for external connection. The samples are then laser-cut into the desired size and shape and sintered in a normal atmosphere in the sintering oven and following the sintering profile of Fig. 2-21. The photograph of the fabricated inductors is shown in Fig. 2-22(d).

2.4.8 Conductivity and Solderability Improvement

The addition of glass and other additives into the silver paste results in the lowering of the conductivity of the sintered silver. Measurements of the conductivity of the

sintered Ag/Pt paste will be elaborated in Chapter 3 of the dissertation. The external metallization of the component can be electroplated with copper to improve the solderability of the sintered Ag/Pt paste and to improve the contact resistance [67]. Fig. 2-23 shows a multi-conductor inductor sample with electroplated copper electrodes.

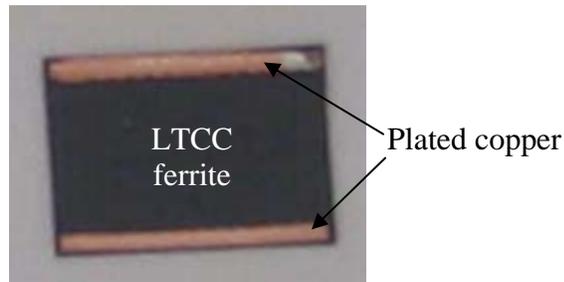


Figure 2-23 Electrodes of inductor electroplated with copper to improve solderability.

Electroplating the contacts with copper reduces the contact resistance of the sample. The overall resistance is reduced from 36 m Ω to 15 m Ω as measured by a DC ohmmeter. Parasitic contact resistance is especially crucial for inductors with low inductance values and low dc resistance values.

2.5 Conclusions for Chapter 2

The application of weight to thin LTCC ferrite tape samples prior to sintering prevents warping of the samples. Application of a thin layer of alumina powder alleviates cracking at the edges of LTCC samples of fewer than three layers, which is due to the friction and constraints imposed by the alumina tiles which are used to sandwich the samples prior to sintering. Applying an uneven layer of alumina results in dimpling,

which can be avoided by applying a thin and uniform layer of alumina powder on the samples prior to sintering.

For thin samples in which weight must be applied during sintering, cutting the sample into a circle can help reduce the chance of circumferential cracking of the sample. For thicker samples greater than seven layers, samples will still crack even when the sample is cut into a circle, which is due to the forced escape of gases, which is inhibited by the applied weights. For thick samples, weight does not need to be applied prior to sintering since thick samples conform to the setter tile during sintering. The first temperature ramp rate between room temperature and the binder burnout temperature can be lowered to allow for a slow release of gases before the binder burnout process.

For complete organic burnout to take place, sintering the LTCC ferrite tape samples in an oxidizing ambient is necessary, which makes the use of copper with the LTCC process less attractive. Sintering in a reducing ambient to prevent copper oxidation causes ferrite to reduce into metallic iron. Sintering in an inert ambient to prevent copper oxidation prevents the organic binder burnout process. Severe volume expansion of copper occurs after oxidation, which introduces additional stress on the system, since the ferrite tape surrounding the conductor shrinks upon sintering and copper expands after the process. After subsequent reduction, the copper does not shrink to its original volume. In view of the inherent stress caused by co-firing copper with LTCC ferrite tape and the complexity involved in the requirement of different ambients for sintering LTCC ferrite tape and copper, it can be concluded that it is not feasible to employ copper metallization in our co-firing process with ferrite tape.

In terms of processing, Ag/Pt paste ESL 953 is compatible for processing with LTCC ferrite tape, since the recommended co-firing temperatures of the two tapes are very close. Experimental results of co-firing the Ag/Pt paste with LTCC ferrite tape does not show signs of cracking, delamination, thinning or gapping of the LTCC tapes. Electroplating the contacts with copper reduces the contact resistance of the sample and helps improve solderability.

Chapter 3. LTCC – Material Characterization for Power Magnetics

3.1 Overview

Material characterization is an important step in understanding the properties of the materials used for magnetics integration. In the beginning of this chapter, the dielectric property, in the form of permittivity of the LTCC ferrite tape used for magnetics integration, will be discussed. The major focus of this chapter is on the magnetic characterization of the LTCC ferrite tape discussed in Chapter 2. The various sources of error in core loss measurement are identified and analyzed. Subsequently, the operational influence on electromagnetic characteristics of the LTCC magnetic material, will be explored. The effect of frequency, temperature and pre-magnetization on the electromagnetic characteristics of the LTCC magnetic material will be examined. Finally, a core loss model based on the Steinmetz equation, with temperature and pre-magnetization dependence will be developed. Effect of the temperature and the DC pre-magnetization on the Steinmetz exponents is also studied. Finally, the conductive paste used for forming the windings of the magnetic component is electrically characterized.

3.2 Estimation of Permittivity

Several methods of permittivity measurement have been reported. The dielectric rod resonator method [68] is commonly used to measure the dielectric properties of high permittivity and low loss dielectric materials in the microwave region. In [69], a non-

contact microwave probe is used to observe high frequency microscopic dielectric distributions in the cross-section of a multi-layer ceramic capacitor. The reflection intensities obtained were transformed into dielectric permittivity, which enables measurement of local dielectric property. In [70], a coaxial probe and in [71], a cavity perturbation technique have been used for permittivity measurements. The above techniques are suitable for dielectric characterization of materials in the RF and microwave region.

In this dissertation, permittivity of the ferrite tape is measured by sandwiching the ferrite tape between two conductive layers to form a single layer capacitor structure. The impedance characteristic is measured using the 4294A impedance analyzer, from which the capacitance and the relative permittivity are obtained.

3.2.1 Sample Preparation

Samples of 1cm x 1cm squares were cut from a ferrite tape. Four layers of the tape were laminated at a pressure of 10 MPa (1500 psi) and at a temperature of 70 °C. A square hole, 0.8 cm x 0.8 cm is cut in a piece of kapton tape, which serves as the stencil for printing conductive paste onto the ferrite tape samples. The cut square of the kapton tape stencil is aligned in the center of the ferrite tape squares. Ag/Pt paste is stencil printed onto the ferrite tape squares using a spatula. The sample is dried in air at a 70 °C for 1 hour. The process of stencil printing conductive paste onto the ferrite square and drying is repeated on the reverse side.

The sample is placed on a bed of alumina powder coated alumina tile to prevent the Ag/Pt paste from adhering to the alumina tile. Another piece of alumina powder coated alumina tile is placed on top of the sample to prevent warping of the thin sample. The sample is sintered in air. After sintering, the sample shrunk to 0.8 cm x 0.8 cm. Copper strips are soldered onto the Ag/Pt pads to form external contacts for impedance measurement. Fig. 3-1 shows a capacitor sample for dielectric constant estimation. The silver pads were estimated to be 6.5 mm x 6.5 mm. Two such capacitors have been fabricated for this set of measurements.

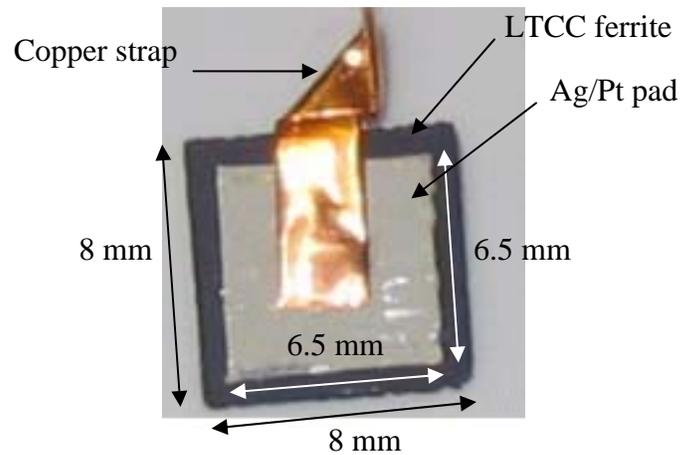


Figure 3-1 Capacitor samples for dielectric constant estimation.

3.2.2 Permittivity Measurement

The impedance characteristics of the samples are measured using the Agilent 4294A impedance analyzer. Fig. 3-2 shows the plot of admittance (Y) vs. frequency. Using $|Y| = 2\pi C f$, where C is the capacitance and f is the frequency, C is estimated to be 19.4pF and 21.8pF from the gradient of the Y vs. f plot, as shown in Fig. 3-2. Using the equation:

$$C = \frac{\epsilon_r \epsilon_0 A}{d}, \quad (3-1)$$

where

ϵ_r : dielectric constant

ϵ_0 : permittivity of free space

A : surface area of conductor

d : thickness of ferrite layer

the thickness of the ferrite layer, $d = 237.5\mu\text{m}$, the surface area of the conductor, $A = 0.65 \times 0.65 \text{ cm}^2$ and the above calculated capacitance values, the dielectric constants were estimated to be 12.3 and 13.8 respectively. The average dielectric constant of the ferrite tape is taken to be approximately 13.

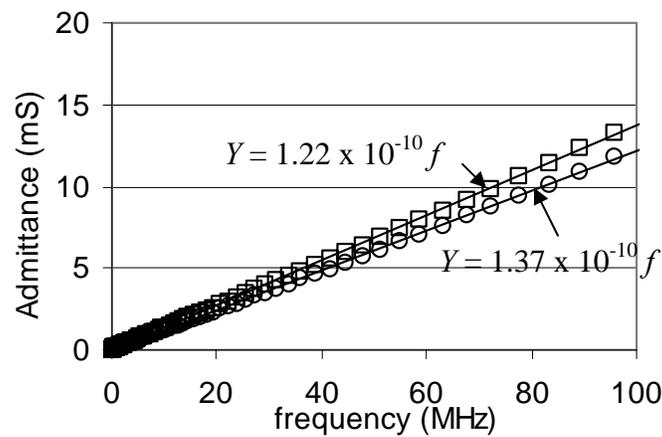


Figure 3-2 Graph of admittance vs. frequency for the two parallel plate capacitor samples.

3.3 Estimation of Core Loss

Numerous core loss characterization techniques have been reported in literature. Core loss can be quantified electrically or by calorimetric means [72]. In electrical characterization of core loss, impedance measurement method [73-75], the CEEC 25300 or CEEC 25000 method [76], or other electrical methods [77] can be applied. In [78], an electrical method is used to characterize core loss of an inductor in a conventional buck-boost converter. An analysis of amplitude and phase shift errors in measurement is made and presented mathematically. In this section, the various sources of error is identified and analyzed in the variation of the European standard CECC25300 or CECC25000 [76] method of characterizing core loss.

3.3.1 Circuit for Loss Measurement

In the measurement of core loss, due to the low permeability of the material and the limited driving capability of the power amplifier used, a capacitor is connected in parallel with the primary windings of the circuit, similar to the European standard CECC 25300 [76], to provide a parallel resonant peak at the frequency of interest. Fig. 3-3 shows the core loss measurement circuit. R is the current sense resistor to sense the current in the primary windings. C_1 is the parallel resonant capacitor. C_2 is the DC blocking capacitor. L_1 is an AC choke.

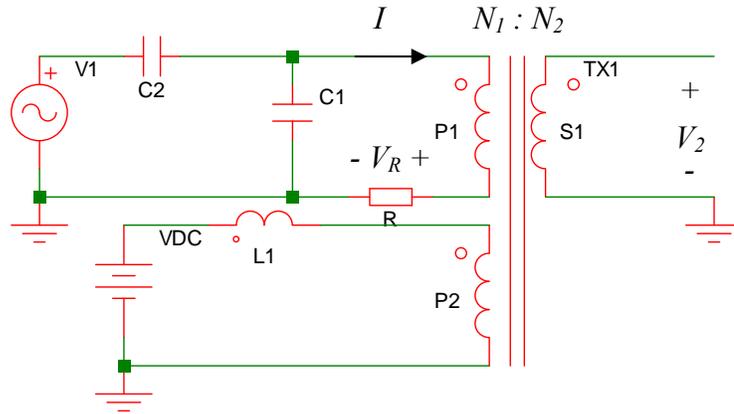


Figure 3-3. Core loss measurement circuit.

3.3.2 Components in Circuitry for Loss Measurement

The LTCC technology for magnetics integration, which is being explored in this dissertation, is targeted at integrating magnetics in small, high power density point-of-load (POL) converters. The technology limits possible sample sizes for core loss measurement. In the measurement of core loss, due to the small size of the magnetic core, low permeability of the material and the limited driving capability of the power amplifier used, a slight modification is made to the circuit similar to the European standard CECC 25300 [76] to accommodate to the above mentioned limitations. A capacitor is connected in parallel with the primary windings of the circuit to provide a parallel resonant peak at the frequency of interest to increase the voltage drop across the primary windings as well as to provide current to the primary windings of the transformer.

In the core loss measurement circuit shown in Fig. 3-3, AC excitation is provided by means of a function generator Agilent 33220A. The AC source is connected to a 25 W RF amplifier from Amplifier Research, of model 25A250A. This constitutes the AC

source V_1 as shown in Fig. 3-3. V_{DC} is provided by means of a DC power supply from Lambda, of model UP6-132. C_2 is a DC blocking capacitor, C_1 is a parallel resonant capacitor to produce a parallel resonant peak at the frequency of interest. R is a current viewing resistor in which the voltage across the resistor is measured to obtain the current. L_1 is an AC choke to reduce the effect of AC perturbation from the primary windings, P_1 . P_2 is the DC windings and S_1 is the secondary windings. The induced voltage, V_2 , is measured across the open circuited secondary windings.

3.3.2.1 Toroidal Core for Loss Measurement

The technology for integrating magnetics in small, high power density point-of-load (POL) converters limits possible sample sizes for core loss measurement. In the measurement of core loss, a bicycle-wheel-like toroidal core made from LTCC ferrite tape is fabricated. The magnetic flux density is approximated to be a constant within the cross-sectional area of the core due to its large radius to core width ratio.

A. Core Design.

In the design of the core dimensions, it is necessary to take into account the power loss for reasonably accurate measurements at low frequency and low magnetic flux densities, effect of non-uniform flux densities on core loss characterization, mechanical and structural reliability of the component under test. To obtain a more uniform flux density distribution, it is desirable to use a core with inner radius close to the outer radius. However, this may pose problems when it comes to the mechanical strength of the core to withstand the stress from wires wound around it. To obtain a more reliable measurement

data, larger power loss is desired, especially at low frequencies and low magnetic flux densities. Hence, the core has to have a volume large enough to ensure measurable losses at low power loss conditions and small enough to be driven by the available power amplifier.

The basic Steinmetz equation [79] is given by:

$$P_v = K_p \cdot f^\alpha \cdot B^\beta \quad (3-2)$$

where

P_v – specific core loss

f – frequency,

B – magnetic flux density

α, β – Steinmetz exponents

K_p – Constant

Using (3-2) and assuming f to be a constant, $P_v \propto B^\beta$. Assuming the magnetic flux density, B , is constant throughout the toroidal core, the power loss, P_l , can be expressed as:

$$P_l \propto B^\beta \pi h [r_o^2 - r_i^2] \quad (3-3)$$

where

h – thickness of the core

r_o – outer radius of the core

r_i – inner radius of the core

For non-uniform B in a toroidal core, power loss, P_2 , can be expressed as:

$$P_2 \propto \frac{2\pi h}{2-\beta} \left(\frac{\mu n i}{2\pi} \right)^\beta [r_o^{2-\beta} - r_i^{2-\beta}] \quad (3-4)$$

where

μ - magnetic permeability

n - number of turns

i - current

The average magnetic flux density, B_{avg} , can be expressed as:

$$B_{avg} = \frac{\mu n i}{2\pi} \cdot \frac{\ln(r_o) - \ln(r_i)}{r_o - r_i} \quad (3-5)$$

The derivation for (3-3), (3-4) and (3-5) can be found in Appendix.

The specific core loss, assuming uniform magnetic flux density, is given by:

$$P_{v1} = \frac{P_1}{\pi h (r_o^2 - r_i^2)} \quad (3-6)$$

The specific core loss assuming non-uniform magnetic flux density is given by:

$$P_{v2} = \frac{P_2}{\pi h (r_o^2 - r_i^2)} \quad (3-7)$$

The % error in specific core loss is:

$$\%error = \left| \frac{P_{v2} - P_{v1}}{P_{v2}} \right| \times 100\% \quad (3-8)$$

Figure 3-4 shows the graph of % error in P_v as a function of the ratio of inner radius to outer radius, $\frac{r_i}{r_o}$. For $\frac{r_i}{r_o} > 0.7$, and assuming β to be 2.2, the error in power loss

estimation assuming B as a constant, is less than 1 %. It is of interest to see what is the %

error in P_v when β varies. Figure 3-5 shows the graph of % error in P_v vs. β for $\frac{r_i}{r_o} = 0.5, 0.75$ and 0.9 . It is observed that for the % error in P_v to be less than 1 % for β in the range of 1 to 3, $\frac{r_i}{r_o}$ has to be greater than 0.75 (see Fig. 3-5).

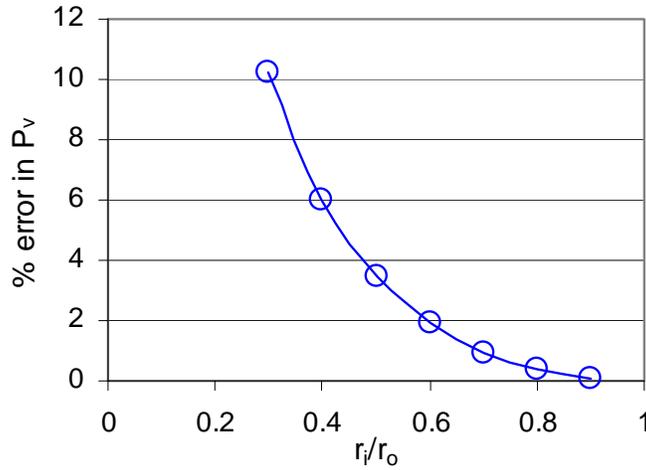


Figure 3-4. Percentage error in specific core loss vs. r_i / r_o .

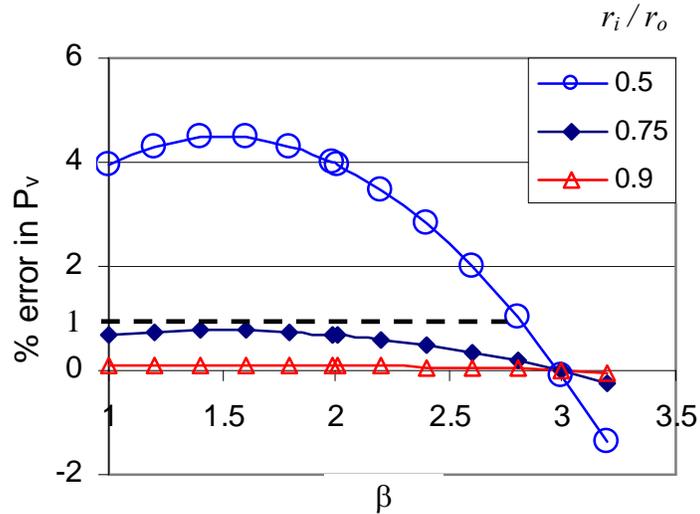


Figure 3-5. Percentage error in specific core loss vs. β for $r_i / r_o = 0.5, 0.75$ and 0.9 .

From measurement results of 4F1 [80] core material, the Steinmetz exponents are estimated to be $\alpha = 1.08$, $\beta = 2.07$, $K_p = 0.001947$. Using these values, the power loss in the core can be estimated. The maximum power loss is designed to be at $f = 4$ MHz and $B_m = 50$ mT. Choosing $\frac{r_i}{r_o} = 0.8$ and core thickness, h , to be 2 mm, the graph of power loss vs. r_o can be plotted as shown in Fig. 3-6.

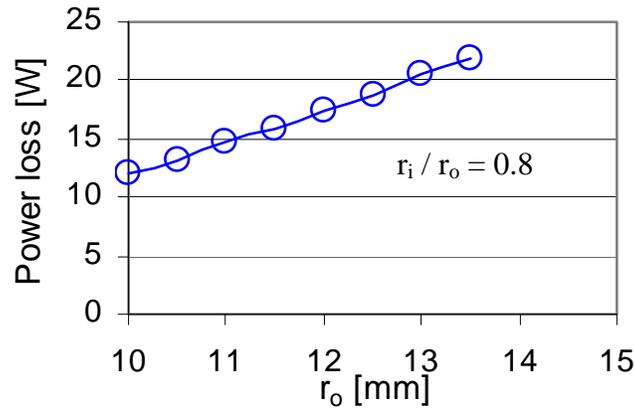


Figure 3-6. Power loss vs. r_o , for $r_i/r_o = 0.8$ and $h = 2$ mm.

The power rating of the power amplifier of model AR 25A250A is 25 W. To give some headroom for other losses and inaccuracies in the assumptions of the Steinmetz exponents, the dimensions of the core is chosen such that the power loss is less than 20 W. Hence, the core dimensions are chosen to be $r_i = 10$ mm, $r_o = 12.5$ mm, $h = 2$ mm.

B. Core Fabrication

In the fabrication of the toroidal core, 42 layers of LTCC tape of dimensions 3.5 mm x 3.5 mm are stacked and laminated as described in Chapter 2.3. Concentric circles of diameter 31.25 mm and 25 mm are subsequently cut on the sample using laser

machining. The cut samples are then placed on an alumina setter tile and sintered in an oven using the sintering profile in Fig. 2-21. Table 3-1 tabulates the toroidal core's dimensions after sintering. Fig. 3-7(a) shows the top view of the geometry of the toroidal core. Fig. 3-7(b) shows the cross-sectional view. Fig. 3-8 shows the photograph of the toroidal core for loss measurement. Table 3-2 tabulates the total core cross-sectional area, volume and average magnetic path length of the core.

Table 3-1 Core Dimensions.

	OD [mm]	ID [mm]	h [mm]
Before sintering	31.40	24.90	2.65
After sintering	25.08	19.94	2.12

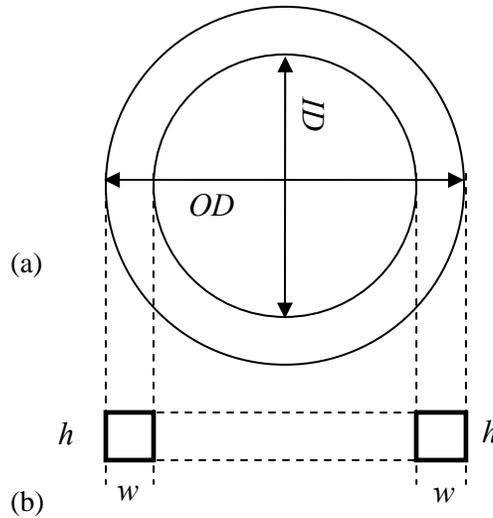


Figure 3-7 Geometry of toroidal core. (a) Top view, (b) cross-sectional view.

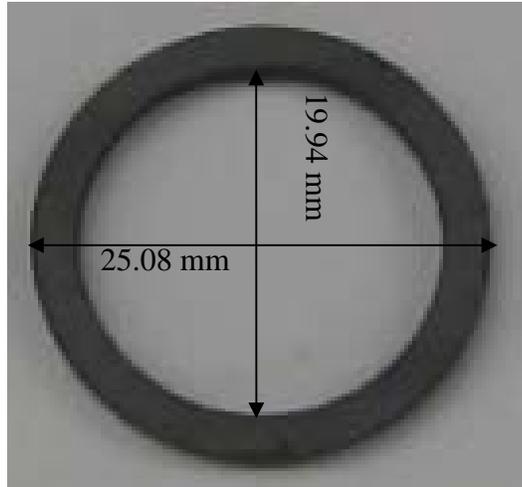


Figure 3-8. Actual toroidal core for loss measurement.

Table 3-2 Total Core Dimensions.

Cross-sectional area [mm ²]	5.444
Volume [mm ³]	384.9
Average magnetic path length, l_m [mm]	70.71

3.3.2.2 Toroidal Core Windings

There are several factors to consider in deciding the number of turns for the primary windings as well as the wire gauge to use. Since a parallel resonant circuit comprising capacitor, C_l , and the primary windings, P_1 , is used, a low resistance is desired for the primary windings. Hence, a wire of smaller AWG is desired. In view of the error caused by the parallel resonance between the inductor and the input capacitance of the probe, it is desired to push the parallel resonant peak to higher frequencies. Hence, the inductance cannot be too large. Using $C_{in} = 11.1$ pF (input capacitance of oscilloscope probe P5050,

as will be elaborated later), the percentage magnitude error vs. inductance at 4 MHz is plotted as shown in Fig. 3-9.

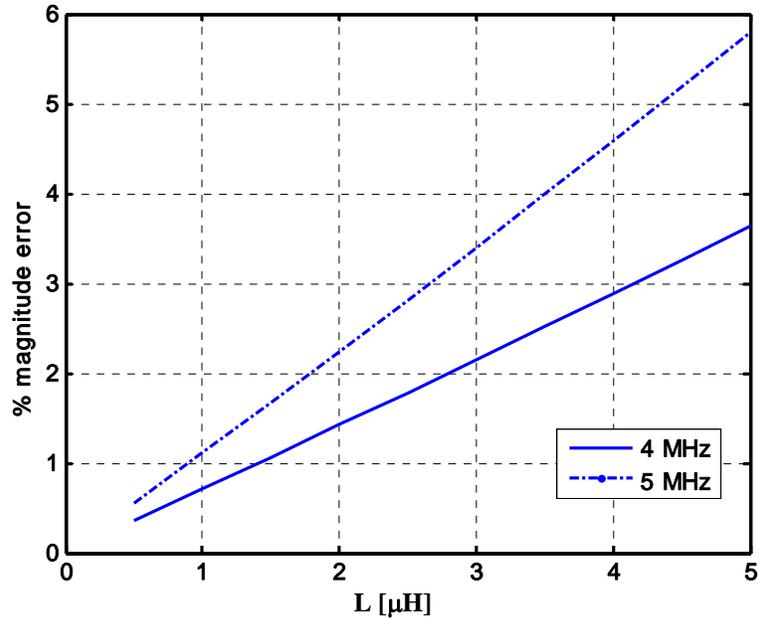


Figure 3-9. Percentage magnitude error vs. inductance at 4 MHz.

For percentage error less than 2.5 %, the inductance has to be less than 3 μH.

Assuming the relative permeability, $\mu_r = 60$, and $L = 3 \mu\text{H}$, and using [81]

$$L = \frac{\mu_r \mu_0 n^2 A}{l_m} \quad (3-9)$$

Where

μ_0 – permeability of free space

A – cross-sectional area

n – number of turns

n is calculated to be 22.9. For better coupling between the primary and secondary coils, the windings are wound in a bifilar fashion, where the number of primary turns is equal

to that of the secondary turns. Hence, the number of turns used for both the primary and secondary coils are 22. This gives a calculated inductance of 2.8 μH . To obtain B_m of 50 mT, the required current can be calculated using [81]

$$B_m = \frac{\mu_r \mu_0 \cdot n \cdot i}{l_m} \quad (3-10)$$

The peak current required is 2.12 A. Setting the maximum current density, $J_{max} = 10 \text{ A/mm}^2$, and using

$$I_{peak} = \sqrt{2} \cdot J_{max} \cdot A \quad (3-11)$$

Table 3-3 tabulates the peak current, I_{peak} , for the wires of AWG between 23 and 27. Wire of AWG 25 is chosen for the primary windings. Since the secondary winding does not carry current, wire of AWG 30 is chosen. The inductance of the primary coils is measured to be 2.51 μH .

Table 3-3 I_{peak} for wires of AWG between 23 and 27.

AWG	d_{wire} [mm]	A [mm^2]	I_{peak} [A]
23	0.573	0.258	3.6468
24	0.511	0.205	2.9003
25	0.455	0.163	2.2995
26	0.405	0.129	1.8219
27	0.361	0.102	1.4475

The length of the wire used for the primary coil with reference to Fig. 3-7, can be estimated by:

$$l_{wire} = \pi \cdot OD + n \cdot 2\pi \cdot \sqrt{\left(\frac{w}{2}\right)^2 + \left(\frac{h}{2}\right)^2} \quad (3-12)$$

where

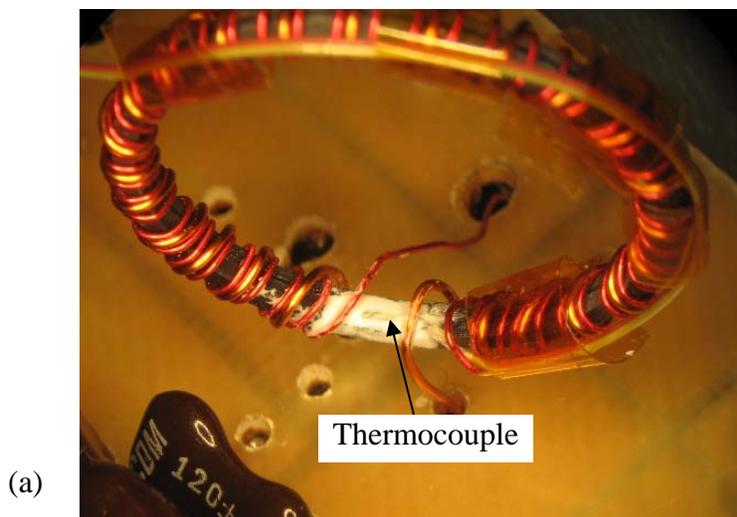
w is the width of the core

h is the thickness of the core

OD is the outer diameter of the core

n is the number of turns on the primary windings

Using $w = 2.5$ mm, $t = 2.115$ mm, $OD = 25$ mm and $n = 22$, l_{wire} is calculated to be 304.9 mm. The actual length of the wire used for the primary windings is 342 mm, which includes additional lengths of wire for connections to the PCB. Fig. 3-10(a) shows a photograph of the toroidal core with windings, and the position of the thermocouple for temperature measurements. Fig. 3-10(b) shows the toroidal core placed on a hot plate and its connection to the circuit via copper straps.



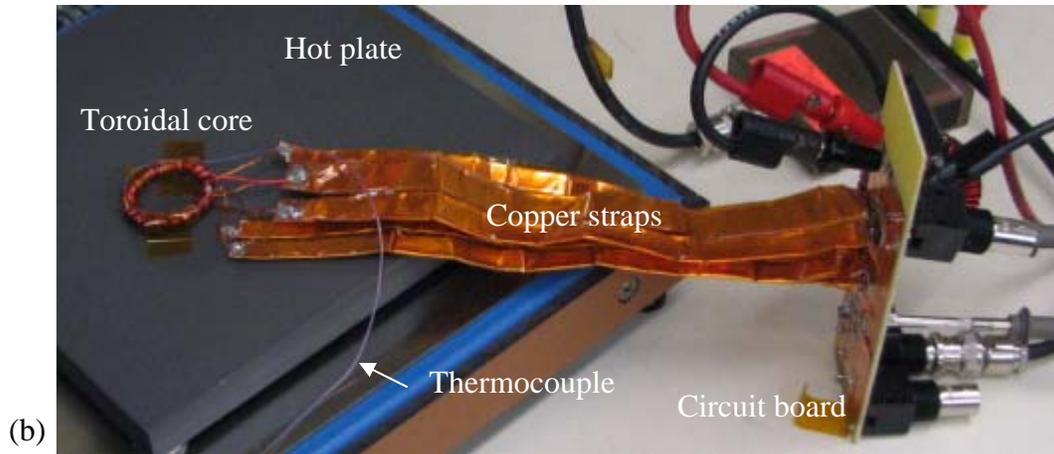


Figure 3-10. Toroidal core for loss measurement. (a) Position of thermocouple on core, (b) toroidal core connection with circuit via copper straps.

Table 3-4 tabulates the AC resistance per unit length, R_{ac}/l of the wire for various frequencies as obtained from Maxwell 2D simulations and the resistance of the primary windings at various frequencies.

Table 3-4 AC resistance per unit length of AWG 25 wire and resistance of primary windings at various frequencies.

f [MHz]	R_{ac} / l [Ω /m]	R_{ac} [m Ω]
1	0.212	72.6
2	0.287	98.3
3	0.345	118.1
4	0.394	134.8

At a maximum AC peak current of 2.12 A, the power loss in the primary windings at 4 MHz is 303 mW, which is far lower than the projected core loss of around 20 W. DC

pre-magnetization is provided by means of a DC winding. Assuming the relative permeability of the core is 60 and the maximum peak-to-peak flux density, B_m , is 50 mT, the corresponding maximum magnetic field intensity, H_{AC} , is calculated to be 663 A/m. In the design of an inductor for VRM applications, the current ripple is designed to be around 40 % of the DC current as a rule of thumb. Following this rule of thumb, we let the AC magnetic flux intensity, H_{AC} , to be 40 % that of the DC magnetic flux intensity, H_{DC} . This gives a value of $H_{DC} = 1658$ A/m. Due to consideration of the availability of the magnet wires, the ease of winding the wire around the core, while minimizing the number of turns of wire wound around the core, magnet wire of AWG 22 is chosen. For $J_{max} = 10$ A/mm², the maximum current is $I_{max} = 3.26$ A. Using the relation $H_{DC} \cdot l_m = N_{DC} \cdot I_{max}$, the number of DC turns is calculated to be 36. To give more headroom, 40 turns are used for the DC winding, and a current of 2.92 A results in a magnetic flux intensity of 1658 A/m.

3.3.2.3 Resonant Capacitor

The purpose of introducing resonant capacitor is to increase the voltage drop across the primary windings of the transformer and to provide current to the primary windings. The capacitance value is chosen such that it resonates with the primary windings and produces high impedance at the frequency of interest. Table 3-5 shows the types of capacitors, their corresponding equivalent series inductance (ESL), equivalent series resistance (ESR) and equivalent parallel resistance (R_p). In the choice of the resonant capacitor, low ESL and ESR are desired. A low ESL will help push the self resonant frequency to higher frequencies and produce less impact on the parallel resonant peak. A

low ESR can reduce its impact on the Q factor of the parallel resonant peak. R_p is related to the leakiness of the capacitor. A capacitor with high R_p is desired as opposed to one with a low R_p . Another important factor in the choice of the capacitors is the voltage rating, which, on the other hand affects the ESL and ESR of the capacitor. For instance, the same type of capacitors with higher voltage rating generally has higher ESL and ESR compared with one of lower voltage rating.

The required values of the parallel resonant capacitances, C_1 , is calculated using equation (3-13).

$$C_1 = \frac{1}{(2\pi f)^2 L_{p1}} \quad (3-13)$$

Table 3-6 tabulates the required parallel resonant capacitors, C_1 , for each frequency.

Table 3-5 Types of Capacitors and their ESL, ESR and R_p [82,83].

	ESL	ESR	R_p	polarized
Electrolytic	high	high	low	yes
Tantalum	low	high	high	yes
Film	mod	low	high	no
Ceramic	v. low	v. low	high	no
Mica/Glass	v. low	v. low	low	no
Trimmer / Variable	low	low	High	no

Table 3-6 Required Parallel Resonant Capacitors, C_1 , for Each Frequency.

f [MHz]	C_1 [nF]
1	10.1
2	2.52
3	1.12
4	0.631
5	0.404

3.3.2.4 Current Sense Resistors

In the choice of current viewing resistors, two types of thick film resistors are compared, which are namely the 2512 and 0603 packages. The resistors for comparison are $1\ \Omega$ resistors. The smaller package resistors have a lower power rating of 0.1 W, which makes it undesirable since the peak AC current passing through the primary coils is designed to be 2.12 A, as mentioned in section 3.3.3.2. On the other hand, the 2512 package resistors have a rating of 2 W, which makes it more desirable for this application. The current sense resistance should not be too large since it is in series with the primary coils and may decrease the Q factor of the parallel branch of C_1 and the primary coils. Besides, the current sense resistance should not be too small as it may pose problems in the accurate measurement of voltage across itself. Hence, the resistance chosen is $0.5\ \Omega$, which is two $1\ \Omega$ resistors in parallel. Since the peak current is designed to be 2.12 A, the maximum power dissipation in the two parallel resistors is 1.12 W each, which is below the power rating of the resistors. The Q factor is 31, which is still reasonably large. The minimum current is designed to be 0.212 A. This translates to a

voltage of 106 mV to be measured across the current sense resistors, which is sufficiently large to be measured by the oscilloscope probe.

3.3.2.5 DC Blocking Capacitor

The purpose of the DC blocking capacitor, C_2 , serves to prevent any DC voltage from biasing the primary coils. Hence, its AC impedance has to be sufficiently small. For the DC blocking capacitor, a ceramic capacitor is chosen due to its low ESR and ESL (see Table 3-5). Although a 100 μF capacitor theoretically yields an impedance of 1.6 m Ω at 1 MHz, however, due to the presence of ESL of the capacitor, the self resonant frequency occurs below 1 MHz, which results in higher actual impedance observed, as illustrated in Fig. 3-11. The actual impedance between 1 to 5 MHz lies in the range of 45 to 200 m Ω .

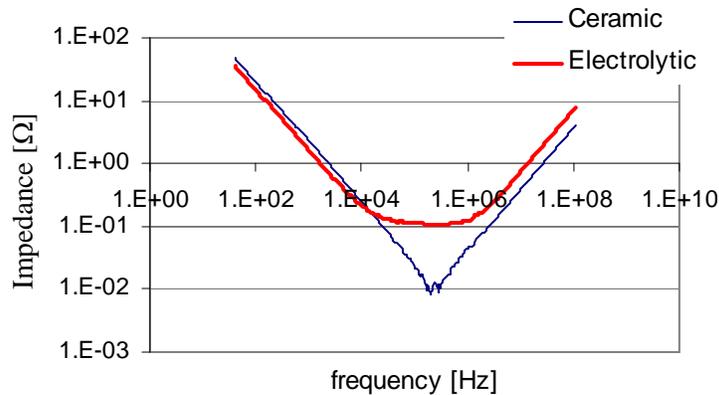


Figure 3-11 Impedance characteristics of a 100 μF ceramic capacitor and a 100 μF electrolytic capacitor.

3.3.2.6 AC choke

The purpose of the AC choke, L_1 , serves to minimize the impact of AC signals on the DC coils. Hence, its AC impedance has to be sufficiently large. The choke has an

inductance of 162.3 μH . The choke is designed such that its self-resonant frequency is above our frequency of interest, while ensuring a sufficiently large impedance. Figure 3-12 shows the magnitude and phase plot of the AC choke measured using an impedance analyzer. As observed from Fig. 3-12, the self resonant frequency is 5.83 MHz, which is above the frequency range of interest (1 to 4 MHz). This will ensure inductive behavior in our frequency range of interest.

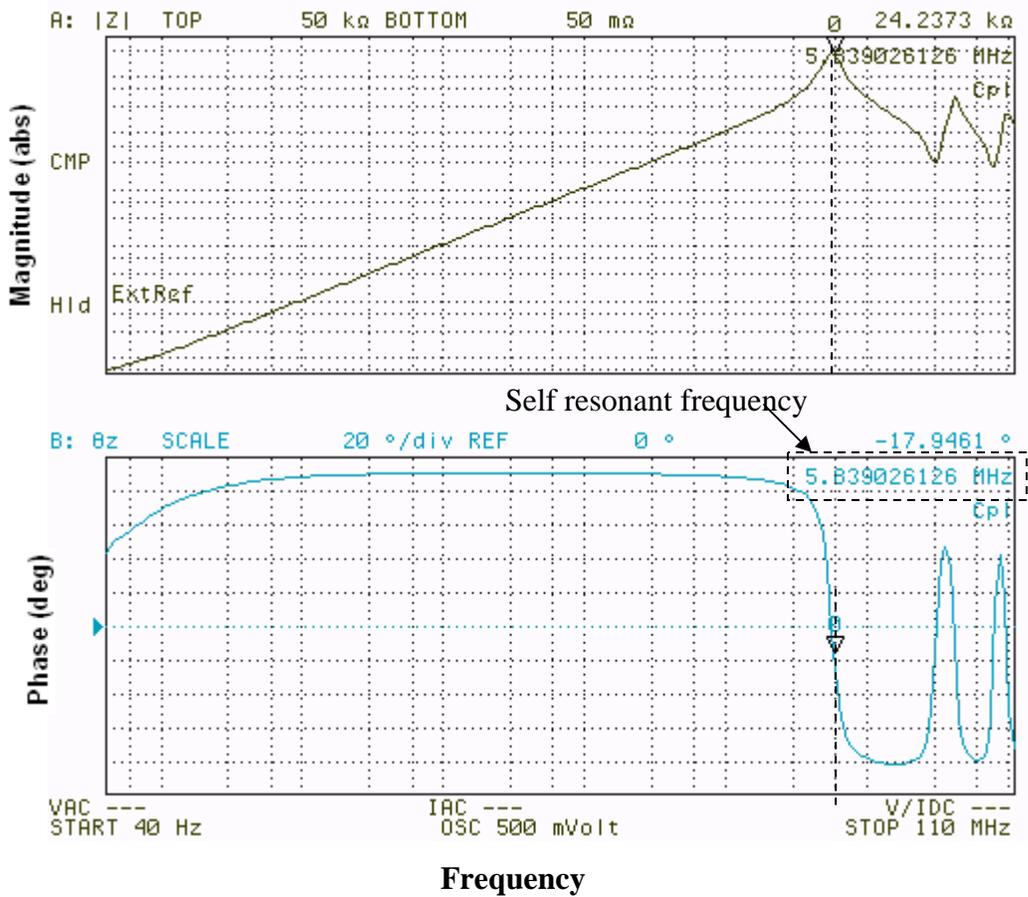


Figure 3-12 Impedance characteristics of AC choke (a) Magnitude vs. frequency, (b) phase vs. frequency.

3.4 Sources of Measurement Error

Accuracy in high frequency electrical characterization of a low loss magnetic material proves to be a challenge due to the large angle between the voltage and current waveforms measured. Any displacement of the measured voltage and current waveform in time can result in large errors in power loss measurement. Two basic types of error are magnitude error and phase error in the measured waveforms [78]. These errors can be come from various sources in the measurement circuit. In this section, the various sources of error will be identified and analyzed.

3.4.1 Error due to Oscilloscope

A. Magnitude Error

The magnitude error from an oscilloscope measurements arises from the vertical resolution of the oscilloscope. The minimum power loss measurement error due to an oscilloscope can be expressed as shown in equation (3-14) [84, page 178]. For 8 bits resolution, the minimum magnitude error is 0.39 % and the minimum power loss error is 0.78 %, assuming the waveform spans the entire oscilloscope screen. If the waveform spans half the oscilloscope screen, the magnitude error is 0.78 % and the power loss error is 1.57 %.

$$\text{Power loss error} = \max\left(\frac{(1 + \frac{1}{2^n})^2 - 1}{1}, \frac{1 - (1 - \frac{1}{2^n})^2}{1}\right) \times 100\% \quad (3-14)$$

where n is the number of bits

Hence, for waveforms spanning between half the screen in the vertical direction to the entire screen, the magnitude error will be between 0.39 % to 0.78 %. If two probes are used in the measurement of the power, where the two voltages are multiplied, their errors add up. The power loss error is between 0.78 % to 1.57 %.

B. Phase Error

The phase error from an oscilloscope measurement results from the sampling rate used. For a sampling rate of 5 GS/s, the phase error induced is [84]

$$\text{Phase error} = \frac{360^\circ \times f}{5 \times 10^9} \quad (3-15)$$

For a single probe, for a 1MHz signal the phase error is 0.072° and for a 5 MHz signal, the phase error is 0.36°.

3.4.2 Errors due to Probe / Cable

A. Magnitude Error

The measurement of voltages across an inductor can result in a magnitude error as a result of resonance with the input capacitance of the measurement probe or cable. Capacitive loading of the device under test (DUT) becomes increasingly important as frequency increases [85]. The problem is aggravated when ringing is introduced into the circuit when used with long ground leads. This implies the need for careful electrical grounding. Input capacitance of a 2 feet coaxial cable, Tektronix P5050 [86] and P6243 [87] oscilloscope probes are measured using the Agilent 4294A impedance analyzer with 42941A probe. Figure 3-13 shows the equivalent circuit of voltage measurement across secondary side of transformer. Fig. 3-14 shows the percentage magnitude error vs.

frequency due to parallel resonance between the inductor and input capacitance of probe with different input capacitances. Table 3-7 tabulates input capacitance, resonant frequency and magnitude error for measuring voltage across a 3 μH inductor, as an example, using the 2 feet coaxial cable, P5050 and P6243 oscilloscope probes.

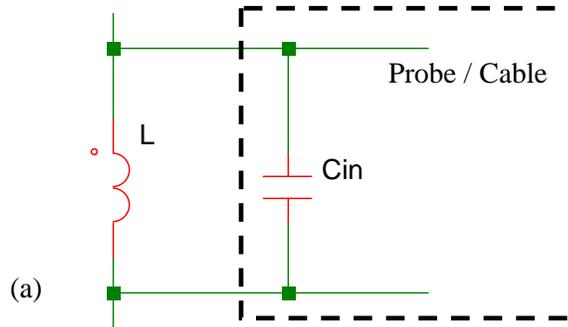


Figure 3-13. Equivalent circuit of voltage measurement across secondary side of transformer

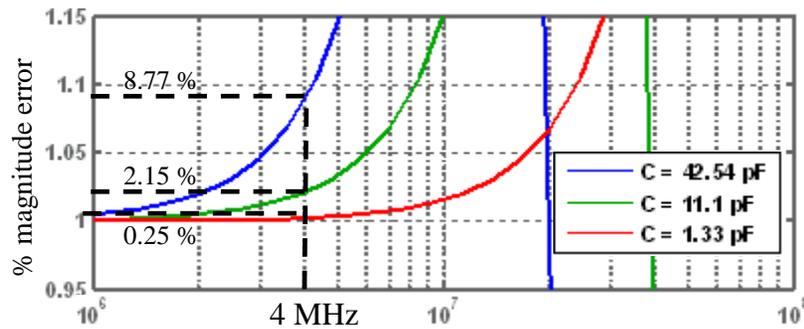


Figure 3-14. Percentage magnitude error due to resonance between inductance of coil ($L = 3 \mu\text{H}$) and input capacitance of probe.

It is clear that at higher frequencies, using a coaxial cable for measuring voltages across inductors generate large magnitude errors, as a result of large input capacitance. Although P6243 has the smallest input capacitance, its major limitation is its low input voltage range of $\pm 15 \text{ V}$. The P5050 is chosen due to its higher voltage rating of $\pm 300 \text{ V}$ and wide bandwidth of 500 MHz. Figure 3-15 shows the percentage magnitude error vs.

inductance using oscilloscope probe P5050 with input capacitance of 11.1 pF. The magnitude error at 5 MHz when measuring voltage across an inductance of 3 μH is 3.4%.

Table 3-7 Input capacitance, resonant frequency and magnitude error for measuring voltage across a 3 μH inductor.

	Coax	P5050 [86]	P6243 [87]
Input capacitance [pF]	42.54	11.1	1.33
Resonant frequency [MHz]	17.3	33.8	97.6
Mag error at 1 MHz [%]	0.51	0.13	0.016
Mag error at 4 MHz [%]	8.77	2.15	0.25
Mag error at 5 MHz [%]	14.4	3.40	0.40

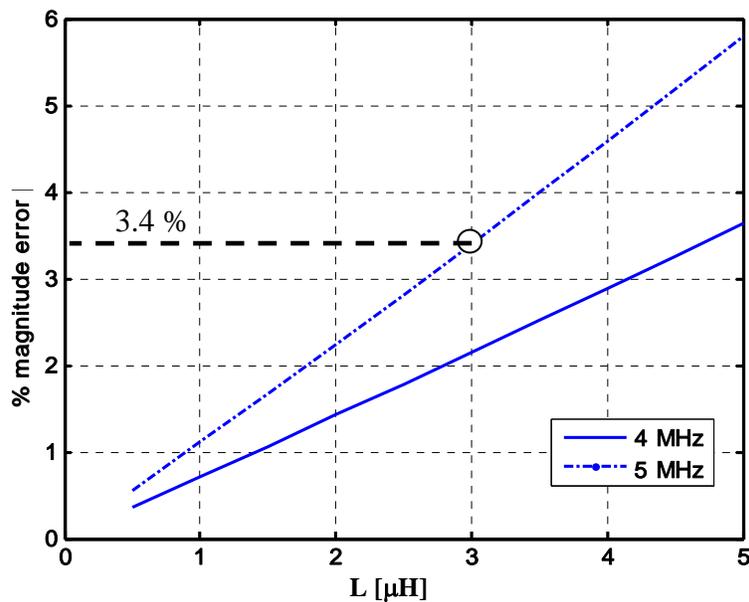


Figure 3-15. Percentage magnitude error vs. inductance using oscilloscope probe P5050 with input capacitance of 11.1 pF.

B. Phase Error

The bandwidth of the probe can result in a phase error in voltage measurements. Assuming first order filter characteristics, the phase error for a 500 MHz probe at 1 MHz is -0.1145° and at 5 MHz is -0.5724° . If the same type of probe is used for measuring voltage across the secondary coils as well as voltage across the current sense resistors, the phase error due to bandwidth will cancel out.

Another source of phase error results from the propagation delay of the probe or cable. When two voltage measurements are taken simultaneously, the propagation delay is the difference between their propagation delays. However, their tolerances add up. For instance, if two Tektronix P6243 probes are used, the error due to propagation delay will be ± 0.4 ns (see Table 3-8). Table 3-8 tabulates the phase error due to propagation delay for a 2 feet coaxial cable and the Tektronix P5050 and P6243 oscilloscope probes.

Table 3-8 Propagation delay and phase error for a 2 feet coaxial cable and the P6134 and P6243 oscilloscope probes.

	Coax	P5050 [86]	P6243 [87]
Propagation delay [ns]	2.0	5.5	5.3 ± 0.2
Phase error @ 1MHz	0.72	1.98	1.91
Phase error @ 5MHz	3.6	9.9	9.54

Since P5050 is used and the tolerance is not given in the datasheet, the phase error due to this tolerance is not considered. Since P5050 probe is used for both measuring

voltage across the secondary coils as well as voltage across the current sense resistors, the propagation delay of 5.5 ns is assumed to cancel out.

3.4.3 Error due to Current Sense Resistor

A. Magnitude Error

The choice of current sense resistors determines the magnitude error it causes. One source of error is the tolerance of the resistor. For a 1 Ω , 1 % resistor, the error range is from 0.995 Ω to 1.005 Ω . Another source of magnitude error is due to the equivalent series inductance (ESL) of the sense resistor. However, since the internal structure of the resistor is unknown and the ESL is too small to be measured accurately, its impact on the magnitude error is not considered here. Fig. 3-16 shows the equivalent circuit for voltage measurement across the current sense resistor.

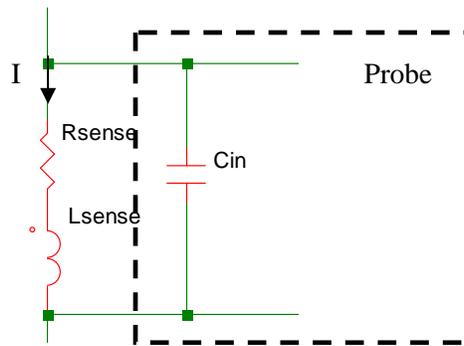


Figure 3-16. Equivalent circuit of voltage measurement across current sense resistor.

In summary, the magnitude error due to the current sense resistors is $\pm 0.5\%$.

B. Phase Error

Since the internal structure of the resistor is unknown and the ESL of the current sense resistor is too small to be measured accurately, its impact on the phase error is not considered here.

3.4.4 Error due to Noise in Measurement

The ground return loop, in addition to resonating with the probe's input capacitance and affecting probe rise time, picks up noise from electromagnetic fields from the environment. The voltage that is induced is proportional to the enclosed loop area [88]. Hence, it is necessary to minimize this loop area. Fig. 3-17 shows the oscilloscope screen with the noise band and the offset voltage. Since the noise is statistical in nature, the noise can be eliminated by taking an average. However, the offset voltage has to be taken into account in the measurements.

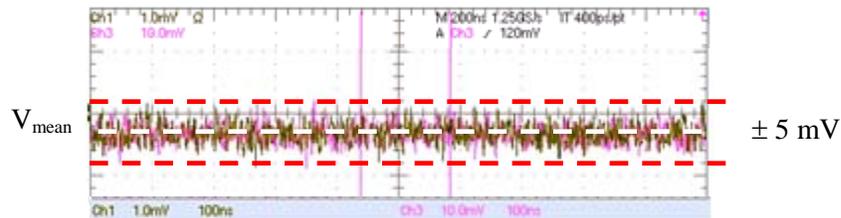


Figure 3-17. Oscilloscope screen with the noise band and the offset voltage.

3.4.5 Error due to Phase shift between V and I

For a voltage and a current waveform displaced at an angle of θ , the power loss is given by:

$$P = VI \cos(\theta) \quad (3-16)$$

The relative measurement error in the power loss calculation is [84, page 186]:

$$\frac{\Delta P}{P} = \frac{\Delta I}{I} + \frac{\Delta V}{V} + \tan(\theta) \cdot \Delta\theta \quad (3-17)$$

where ΔP , ΔI , ΔV and $\Delta\theta$, are the perturbations in P , I , V and θ respectively. Fig. 3-18 shows the power loss measurement error vs. phase shift between V and I for phase error of 0.1° , 1° and 10° . A more detailed analysis has been described in [84]. From Fig. 3-18, it is clear that the error in the power loss measurement increases as the phase shift between the voltage and the current increases. The error increases rapidly as the phase shift is greater than 80° .

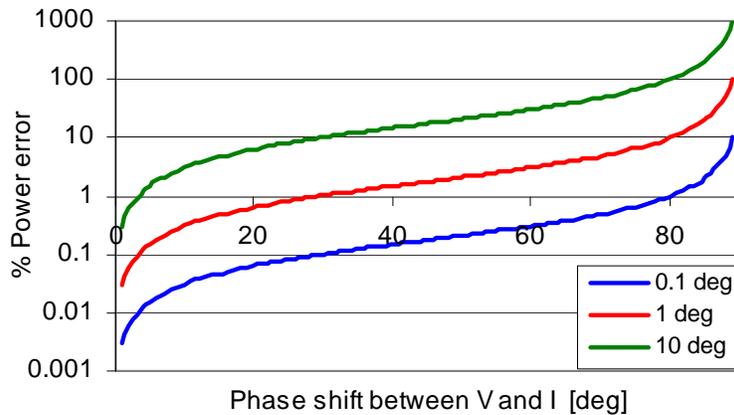


Figure 3-18. Power loss measurement error vs. phase shift between V and I for phase error of 0.1° , 1° and 10° .

3.4.6 Summary

In summary, magnitude and phase errors in measurements affect the accuracy in power loss measurements. Using an oscilloscope with 8 bits vertical resolution results in a magnitude error of $\pm 0.78\%$. With a sampling rate of 5 GS/s, the phase error is $\pm 0.144^\circ$ for 1 MHz and $\pm 0.576^\circ$ for 4 MHz. Measurement of an inductor using an oscilloscope probe causes a magnitude error due to the parallel resonance with the input capacitance of

the probe. The bandwidth of the probe can result in a phase error in voltage measurements. The other source of error results from the propagation delay of the probe or cable. However, when two probes of the same type are used simultaneously to obtain voltage waveforms, these two errors in phase cancel out. The choice of current sense resistors determines the magnitude error it causes. For a resistor with tolerance of 1 %, the magnitude error in voltage measurement is ± 0.5 %. Noise in voltage measurement is statistical in nature, which can be eliminated by taking an average. However, the offset voltage has to be taken into account in the measurements. For instance, the mean of a complete cycle has to be subtracted from the voltage waveform before using it for loss calculations. The phase shift between the voltage and current waveforms affects its susceptibility to small phase errors in measurement. Tables 3-9 and 3-10 summarize the magnitude and phase errors respectively.

Table 3-9 Summary of Magnitude Error.

Source of error	$f = 1\text{MHz}$	$f = 4\text{ MHz}$
1. Oscilloscope (resolution = 8 bits)	± 0.78 %	± 0.78 %
2. Probe	+ 0.13 %	+ 2.15 %
3. Sense resistors	± 0.5 %	± 0.5 %
4. Measurement noise	N/A	N/A
Lower bound of magnitude error	- 1.28 %	-1.28 %
Upper bound of magnitude error	1.41 %	3.43 %

Table 3-10 Summary of Phase Error.

Source of error	$f = 1\text{MHz}$	$f = 4\text{ MHz}$
1. Oscilloscope (5 GS/s)	$\pm 0.144^\circ$	$\pm 0.576^\circ$
2. Probe	N/A	N/A
3. Sense resistors	N/A	N/A
4. Measurement noise	N/A	N/A
Lower bound of phase error	$- 0.144^\circ$	$- 0.576^\circ$
Upper bound of phase error	0.144°	0.576°

Assume the original voltage and current waveforms are v and i , where i lags v by an angle ϕ . v_1 and i_1 are the voltage and current waveforms with a positive magnitude error and a phase error which will decrease the phase shift between the voltage and the current, leading to the maximum positive power error. v_2 and i_2 are the voltage and current waveforms with a negative magnitude error and a phase error which will increase the phase shift between the voltage and the current, leading to the maximum negative power error. The voltages, currents, power and power error are as defined:

$$v = V_0 \sin(\omega t) \quad (3-18)$$

$$i = I_0 \sin(\omega t - \phi) \quad (3-19)$$

$$v_1 = (1 + \Delta M_u) V_0 \sin(\omega t) \quad (3-20)$$

$$i_1 = (1 + \Delta M_u) I_0 \sin(\omega t - \phi + \Delta\phi) \quad (3-21)$$

$$v_2 = (1 - \Delta M_l) V_0 \sin(\omega t) \quad (3-22)$$

$$i_2 = (1 - \Delta M_l) I_0 \sin(\omega t - \phi - \Delta\phi) \quad (3-23)$$

$$p = v \cdot i \quad (3-24)$$

$$p_1 = v_1 \cdot i_1 \quad (3-25)$$

$$p_2 = v_2 \cdot i_2 \quad (3-26)$$

$$\% \text{ maximum positive power error} = \frac{p - p_1}{p} \times 100\% \quad (3-27)$$

$$\% \text{ maximum negative power error} = \frac{p - p_2}{p} \times 100\% \quad (3-28)$$

where

V_0 - peak voltage

I_0 - peak current

ω - angular frequency

t - time

ϕ - phase shift between voltage and current

ΔM_u - upper bound of magnitude error

ΔM_l - lower bound of magnitude error

$\Delta\phi$ - phase error

Figure 3-19 shows the percentage power error vs. phase shift between current through primary coils and voltage across secondary coils for 1 MHz and 4 MHz signal, using (3-27) and (3-28), considering total magnitude error and total phase error.

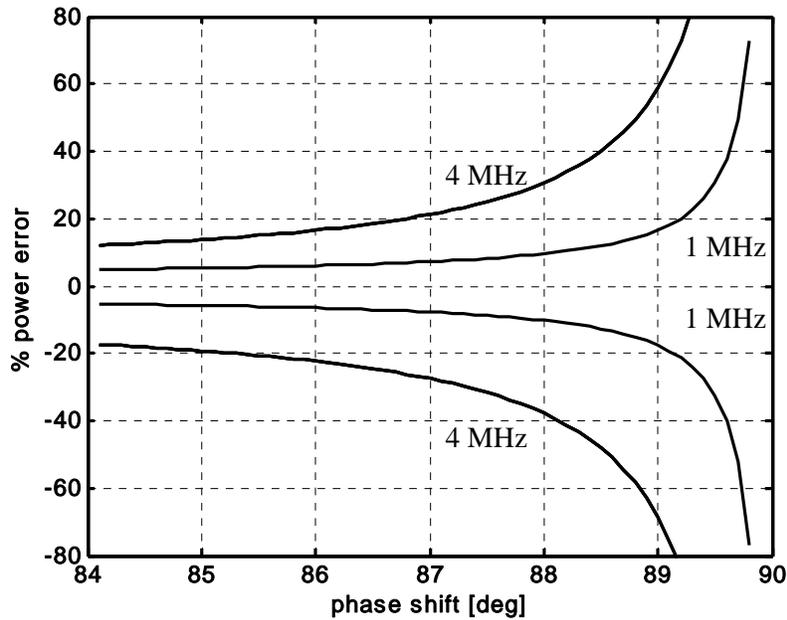


Figure 3-19. Percentage power error vs. phase shift between current through primary coils and voltage across secondary coils for 1 MHz and 4 MHz, considering total magnitude error and total phase error.

3.5 Operational Influence on Electromagnetic Characteristics of LTCC

Magnetic Material

Numerous loss models have been developed to characterize core losses in magnetic materials. Jiles and Atherton [89], Coleman and Hodgdon [90], and Preisach [91] developed the static hysteresis models. Subsequently, frequency dependent losses [92-97] has been included into the above static models. The most common and widely used method is the Steinmetz equation [79], which relates volumetric power loss to magnetic flux density and frequency. The Steinmetz equation has been subsequently modified to include losses due to DC premagnetization [98], influence of non-sinusoidal waveforms [73, 99] and remagnetization [100] and temperature [79].

In this dissertation, Steinmetz equation with temperature dependence [79] is used to model core loss. The temperature coefficients include magnetic flux density dependence with temperature and temperature dependence of the Steinmetz exponents. Effect of DC pre-magnetization on these coefficients and exponents is also studied.

3.5.1 Effect of Frequency on Electromagnetic Characteristics

The basic Steinmetz equation is given by:

$$P_v = K_p \cdot f^\alpha \cdot B^\beta \quad (3-29)$$

In this set of measurements, frequency is varied and the Steinmetz exponents are obtained for each frequency. Fig. 3-20 shows the specific power loss vs. peak-to-peak flux density for frequencies between 1 to 5 MHz. From Fig. 3-20, the gradient of the curves yields β and the vertical intercept yields $\log(K_p \cdot f^\alpha)$. The average β for 1 MHz to 5 MHz is 2.06. Fig. 3-21 shows the plot of $\log(K_p \cdot f^\alpha)$ vs. $\log(f)$. From Fig. 3-21, α is estimated to be 1.255 and K_p is 1.32×10^{-5} .

Hence for $T = 26^\circ\text{C}$ and $I_{DC} = 0$ A, the volumetric power loss can be expressed as:

$$P_v = 1.32 \times 10^{-5} \cdot f^{1.255} \cdot B^{2.06} .$$

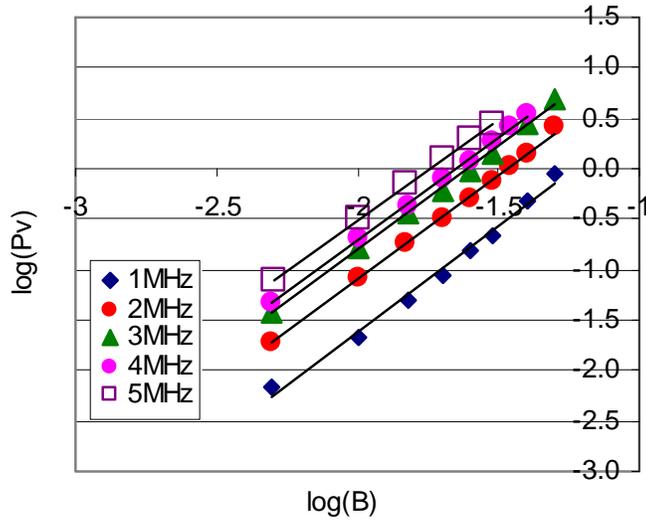


Figure 3-20 Specific power loss vs. peak-to-peak flux density for frequencies between 1 to 5 MHz at $T = 26\text{ }^{\circ}\text{C}$ and $I_{DC} = 0\text{ A}$.

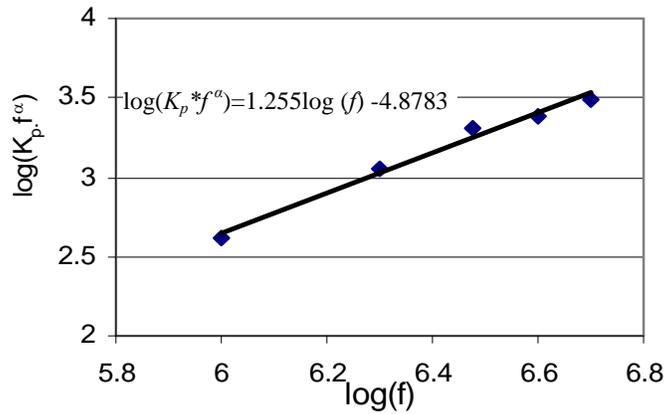


Figure 3-21 Graph of $\log(K_p \cdot f^\alpha)$ vs. $\log(f)$ at $T = 26\text{ }^{\circ}\text{C}$ and $I_{DC} = 0\text{ A}$.

3.5.2 Effect of Pre-magnetization on Electromagnetic Characteristics

The loss measurement described above is repeated for frequencies between 1 MHz to 4 MHz with application of a DC current of $I_{DC} = 0.67\text{ A}$, 1.1 A , 2.2 A and 3.1 A . Fig. 3-22 shows the change of β with I_{DC} . Fig. 3-23 shows the curves of $\log(K_p \cdot f^\alpha)$ vs. $\log(f)$ for I_{DC} between 0 A to 3 A. The gradient of the curves yields α and the vertical intercept

yields $\log(K_p)$. Fig. 3-24 shows the plot of α vs. I_{DC} at $T = 26^\circ\text{C}$ and Fig. 3-25 shows the plot of K_p vs. I_{DC} at $T = 26^\circ\text{C}$. From Fig. 3-22, Fig. 3-24 and Fig. 3-25, α , β and K_p can be expressed as a function of I_{DC} in the form of:

$$\alpha(I_{DC}) = a_1 \cdot I_{DC} + a_2 \quad (3-30)$$

$$\beta(I_{DC}) = b_1 \cdot I_{DC} + b_2 \quad (3-31)$$

$$K_p(I_{DC}) = k_1 \cdot \exp(k_2 \cdot I_{DC}) \quad (3-32)$$

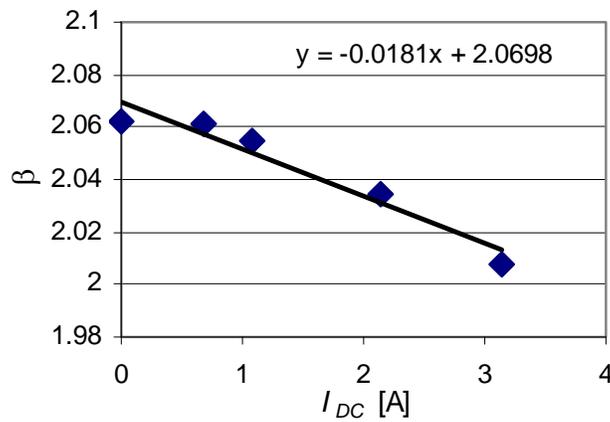


Figure 3-22 Graph of β vs. I_{DC} at $T = 26^\circ\text{C}$.

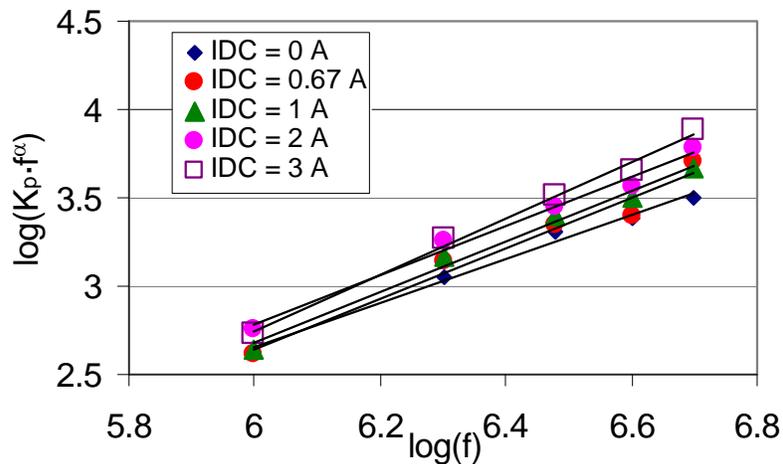


Figure 3-23 Graph of $\log(K_p \cdot f^\alpha)$ vs. I_{DC} at $T = 26^\circ\text{C}$.

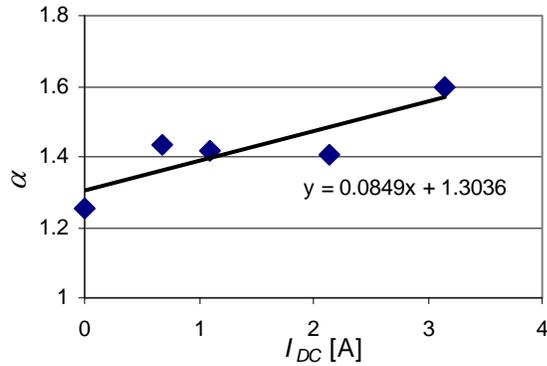


Figure 3-24 Graph of α vs. I_{DC} at $T = 26$ °C.

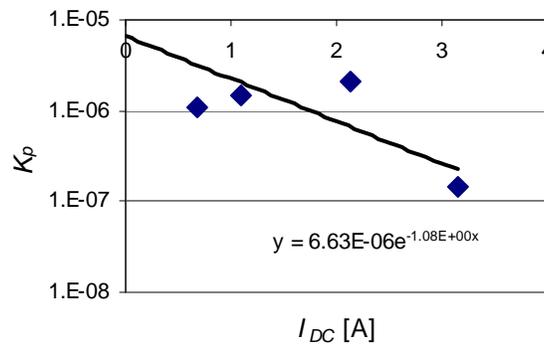


Figure 3-25 Graph of K_p vs. I_{DC} at $T = 26$ °C.

In summary, α and β can be expressed as a linear function of I_{DC} in the range of I_{DC} between 0 A and 3 A. K_p can be expressed as an exponential function of I_{DC} . Hence, specific core loss, P_v , can be expressed as $P_v(f, B_m, I_{DC}) = K_p(I_{DC}) \cdot f^{\alpha(I_{DC})} \cdot B^{\beta(I_{DC})}$.

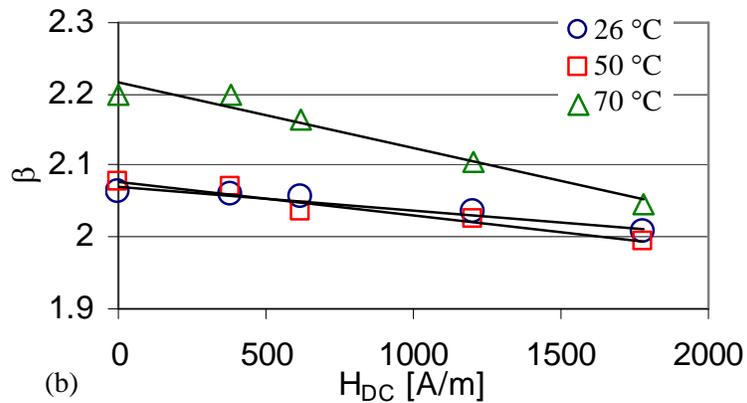
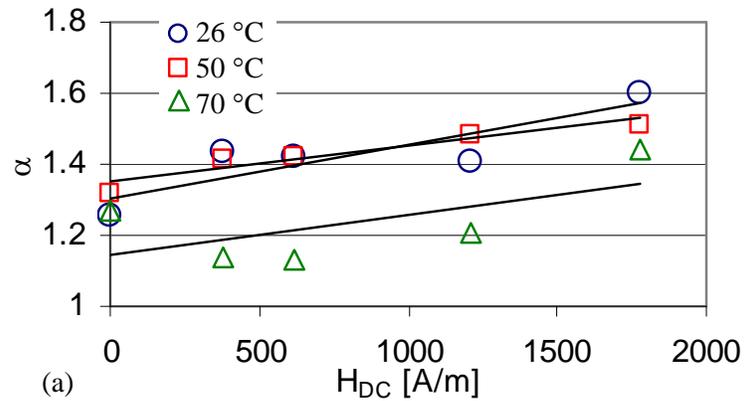
3.5.3 Effect of Temperature on Electromagnetic Characteristics

In this set of experiments, the temperature is varied between 26 °C and 70 °C. The photograph of the connection between the circuit to the core, which is attached to the hotplate is shown in Fig. 3-10(b). Temperature is measured by means of a T type thermocouple. The position of the thermocouple on the core is shown in Fig. 3-10(a).

In the development of the core loss model, Steinmetz equation [79] is used. Equation (3-33) shows the Steinmetz equation taking into account temperature dependence [79].

$$P_v = k' \cdot f^\alpha \cdot B^\beta \cdot (c_{t2}T^2 + c_{t1}T + c_t) \quad (3-33)$$

In addition to the temperature dependence on losses, temperature dependence of Steinmetz exponents is also taken into account. Fig. 3-26 shows the graphs of (a) α vs. I_{DC} , (b) β vs. I_{DC} and (c) K_p vs. I_{DC} . for $T = 26, 50$ and 70 °C. α varies within ± 17.5 % of its mean value and β varies between ± 5 % of its mean value. Fig. 3-27 shows the graphs of the coefficients $a_1, a_2, b_1, b_2, k_1,$ and k_2 (as defined in (3-30) to (3-32)) vs. temperature, T , which are fitted using second order polynomial.



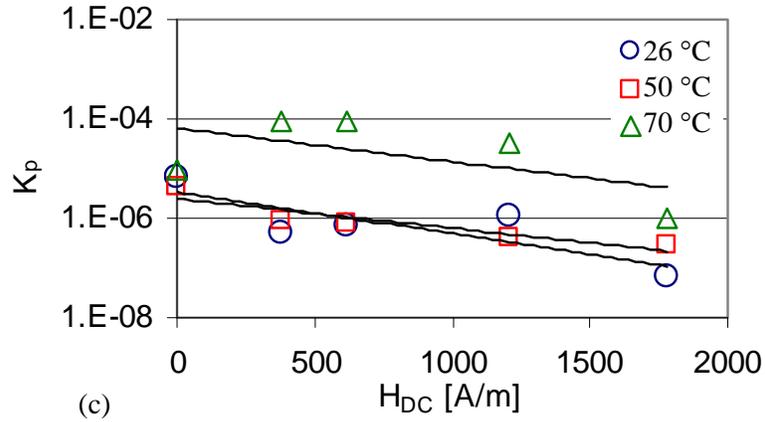


Figure 3-26 Graphs of (a) α vs. I_{DC} , (b) β vs. I_{DC} , and (c) K_p vs. I_{DC} for $T = 26, 50$ and 70 °C.

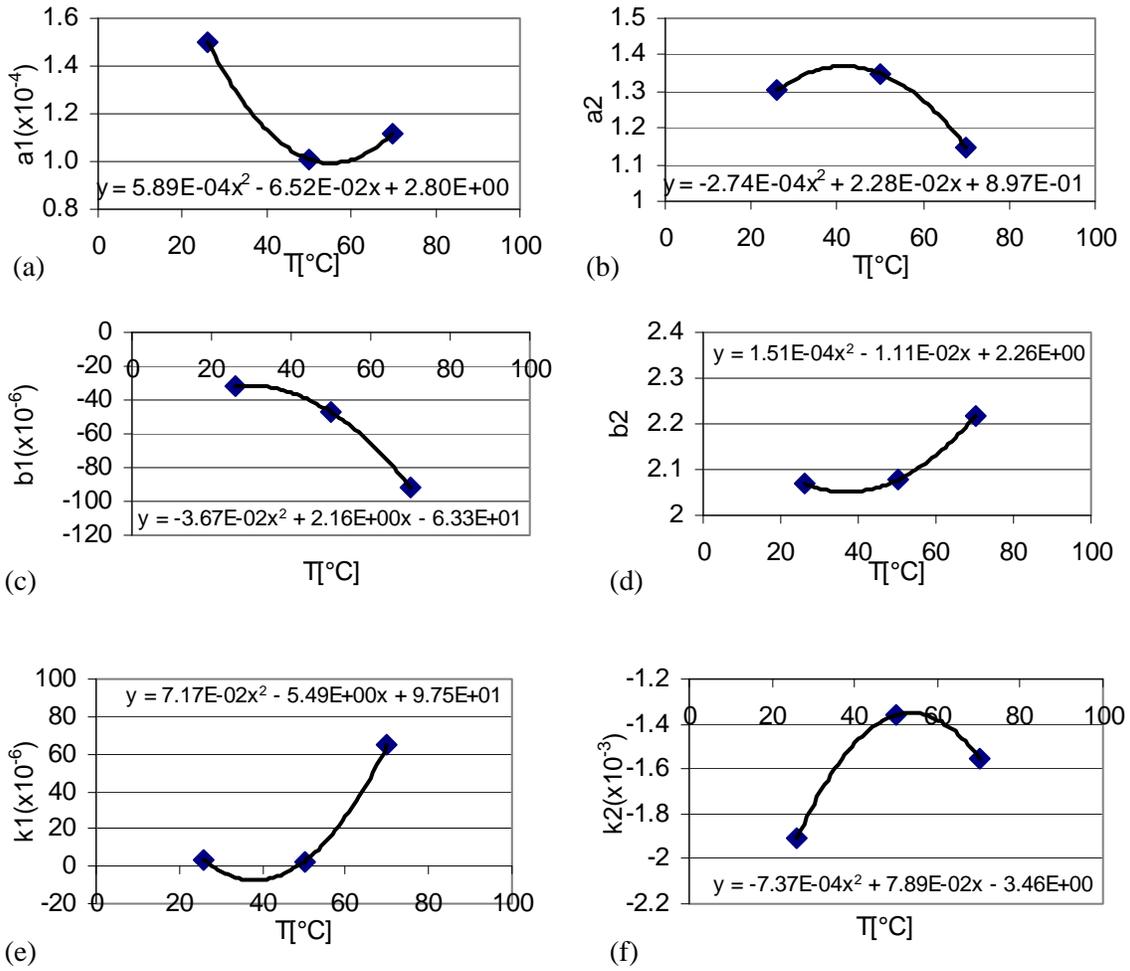


Figure 3-27 Graphs of (a) a_1 vs. T , (b) a_2 vs. T , (c) b_1 vs. T , (d) b_2 vs. T , (e) k_1 vs. T , (f) k_2 vs. T .

The specific core loss can be expressed as:

$$P_v(f, B_m, I_{DC}, T) = K_p(I_{DC}, T) \cdot f^{\alpha(I_{DC}, T)} \cdot B^{\beta(I_{DC}, T)} \quad (3-34)$$

where

$$\alpha(I_{DC}, T) = a_1(T) \cdot I_{DC} + a_2(T) \quad (3-35a)$$

$$\beta(I_{DC}, T) = b_1(T) \cdot I_{DC} + b_2(T) \quad (3-35b)$$

$$K_p(I_{DC}, T) = k_1(T) \cdot \exp(k_2(T) \cdot I_{DC}) \quad (3-35c)$$

$$a_1(T) = 3.41 \times 10^{-5} \cdot T^2 - 3.76 \times 10^{-3} \cdot T + 0.16 \quad (3-35d)$$

$$a_2(T) = -2.74 \times 10^{-4} \cdot T^2 + 2.27 \times 10^{-2} \cdot T + 0.898 \quad (3-35e)$$

$$b_1(T) = -2.08 \times 10^{-5} \cdot T^2 + 1.23 \times 10^{-3} \cdot T - 0.036 \quad (3-35f)$$

$$b_2(T) = 1.51 \times 10^{-4} \cdot T^2 - 1.11 \times 10^{-2} \cdot T + 2.26 \quad (3-35g)$$

$$k_1(T) = 1.43 \times 10^{-7} \cdot T^2 - 1.1 \times 10^{-5} \cdot T - 1.95 \times 10^{-4} \quad (3-35h)$$

$$k_2(T) = -4.11 \times 10^{-4} \cdot T^2 + 4.41 \times 10^{-2} \cdot T - 1.95 \quad (3-35i)$$

The empirical model described by the equation (3-34) and (3-35) is based on the toroidal core of a certain size with a certain number of turns of windings. To use it to estimate core loss for a magnetic component of different dimensions and number of turns of windings, expressing the model as a function of magnetic field intensity would be more appropriate.

The specific core loss can be expressed as:

$$P_v(f, B_m, H_{DC}, T) = K_p(H_{DC}, T, n) \cdot f^{\alpha(H_{DC}, T, n)} \cdot B^{\beta(H_{DC}, T, n)} \quad (3-36)$$

where

$$\alpha(H_{DC}, T, l_m, n) = a_1(T) \cdot H_{DC} + a_2(T) \quad (3-37a)$$

$$\beta(H_{DC}, T, l_m, n) = b_1(T) \cdot H_{DC} + b_2(T) \quad (3-37b)$$

$$K_p(H_{DC}, T, l_m, n) = k_1(T) \cdot \exp(k_2(T) \cdot H_{DC}) \quad (3-37c)$$

$$a_1(T) = 5.89 \times 10^{-8} \cdot T^2 - 6.52 \times 10^{-6} \cdot T + 2.8 \times 10^{-4} \quad (3-37d)$$

$$a_2(T) = -2.74 \times 10^{-4} \cdot T^2 + 2.28 \times 10^{-2} \cdot T + 0.897 \quad (3-37e)$$

$$b_1(T) = -3.67 \times 10^{-8} \cdot T^2 + 2.16 \times 10^{-6} \cdot T - 6.33 \times 10^{-5} \quad (3-37f)$$

$$b_2(T) = 1.51 \times 10^{-4} \cdot T^2 - 1.11 \times 10^{-2} \cdot T + 2.26 \quad (3-37g)$$

$$k_1(T) = 7.17 \times 10^{-8} \cdot T^2 - 5.49 \times 10^{-6} \cdot T - 9.75 \times 10^{-5} \quad (3-37h)$$

$$k_2(T) = -7.37 \times 10^{-7} \cdot T^2 + 7.89 \times 10^{-5} \cdot T - 3.46 \times 10^{-3} \quad (3-37i)$$

Hence, due to the effect of DC pre-magnetization, an additional exponential term is added to (3-36). The specific core loss taking into account effects of I_{DC} and temperature can be expressed as:

$$P_v(f, B_m, H_{DC}, T) = f^{\alpha(H_{DC}, T, n)} \cdot B_m^{\beta(H_{DC}, T, n)} \cdot (c_{t2} \cdot T^2 + c_{t1} \cdot T + c_t) \cdot \exp(k_2(T) \cdot H_{DC}) \quad (3-38)$$

where c_{t2} , c_{t1} , and c_t , are the coefficients of $k_2(T)$.

3.5.4 Model comparison with actual data

The model developed in this section is obtained by empirical means. The accuracy of the model depends on how well the equations describe the data. The discrepancy between the fitted curve and the data plotted on a log scale is usually magnified when plotted on a linear scale. Fig. 3-28 shows the plot of Fig. 3-20 plotted on linear scale, where the dots represent experimental data and the lines are the fitted curves. Figure 3-29 shows the percentage error between the fitted curves and the experimental data vs. magnetic flux density. It is clear from this plot that the error between the basic Steinmetz

model and the experimental data can be as large as several tens of percent. The percentage error between the model and the experimental data is given as:

$$\%error = \frac{P_v(\text{exp}) - P_v(\text{mod})}{P_v(\text{exp})} \times 100\% \quad (3-39)$$

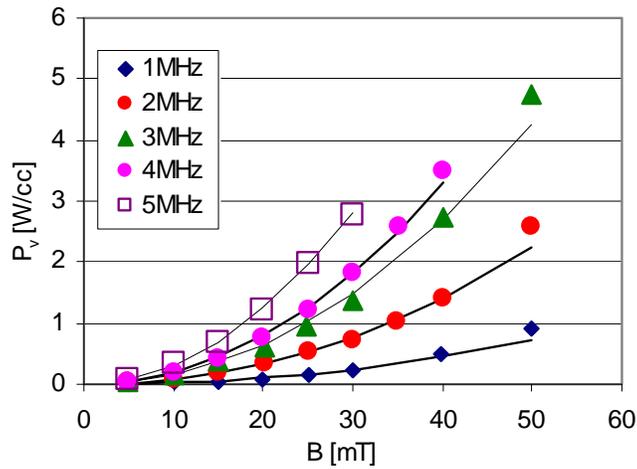


Figure 3-28 Specific power loss vs. peak-to-peak flux density and or frequencies between 1 to 5 MHz at $T = 26\text{ }^\circ\text{C}$ and $I_{DC} = 0\text{ A}$.

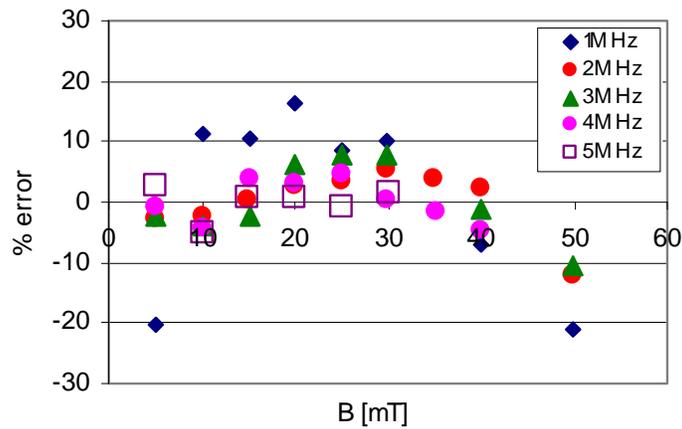


Figure 3-29 Percentage error between fitted curves and experimental data, for frequencies between 1 to 5 MHz at $T = 26\text{ }^\circ\text{C}$ and $I_{DC} = 0\text{ A}$.

Figure 3-30 shows the percentage error between experimental data and model vs. B_m for (a) 1 MHz, (b) 2 MHz, (c) 3 MHz and (d) 4 MHz, at $26\text{ }^\circ\text{C}$, $50\text{ }^\circ\text{C}$, $70\text{ }^\circ\text{C}$ and $I_{DC} = 0$

A and 3 A. The error range is between -65 % to 33 %, which is due to discrepancy between experimental data and fitted curve. Fig. 3-31 is the same as Fig. 3-19, indicating the range of phase shifts between voltage and current waveforms measured at 1 MHz and 4 MHz. The range of phase shift for each frequency is obtained from the experimental voltage and current waveforms to obtain a peak-to-peak flux density in the range of 5 mT to 50 mT, DC magnetic field intensity between 0 A/m to 1780 A/m at a temperature range of 26 °C to 70 °C. The range of phase shift for 1 MHz is 87.8° to 89.2°. The range of phase shift for 4 MHz is 87° to 88°.

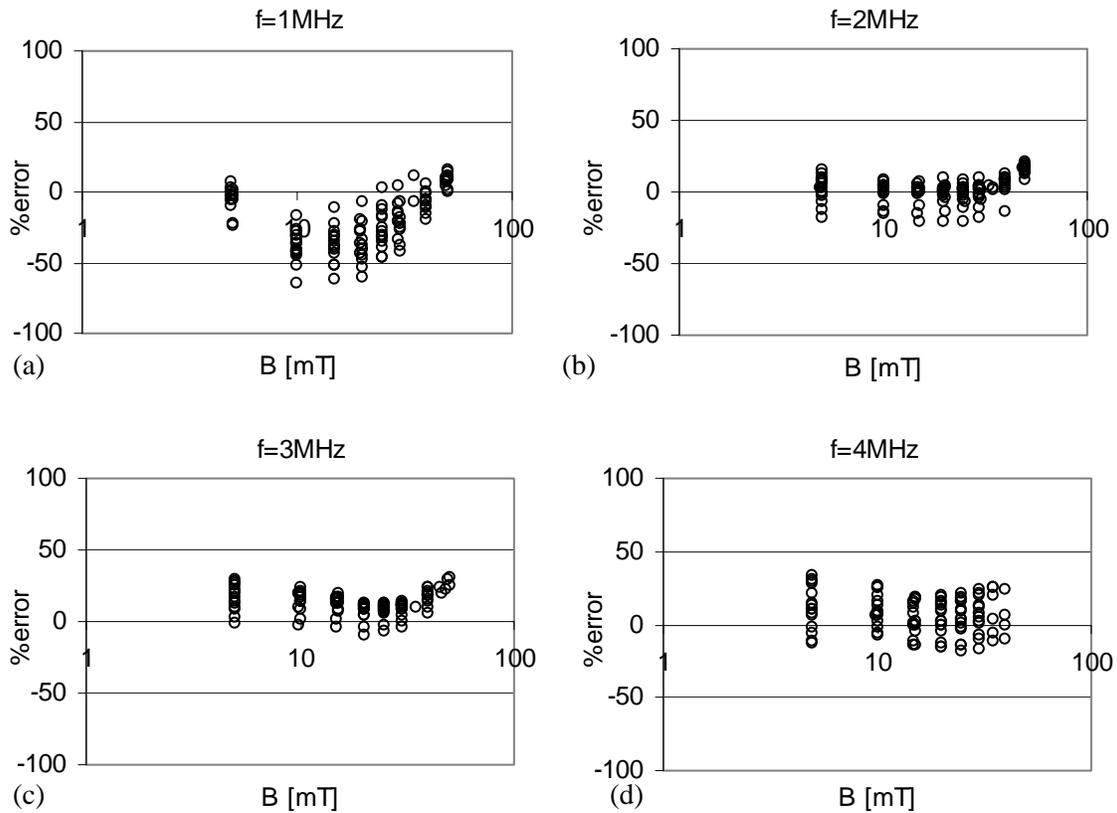


Figure 3-30 Percentage error between experimental data and model vs. peak-to-peak flux density for (a) 1 MHz, (b) 2 MHz, (c) 3 MHz and (d) 4 MHz, at 26 °C, 50 °C, 70 °C and $I_{DC} = 0$ A and 3 A.

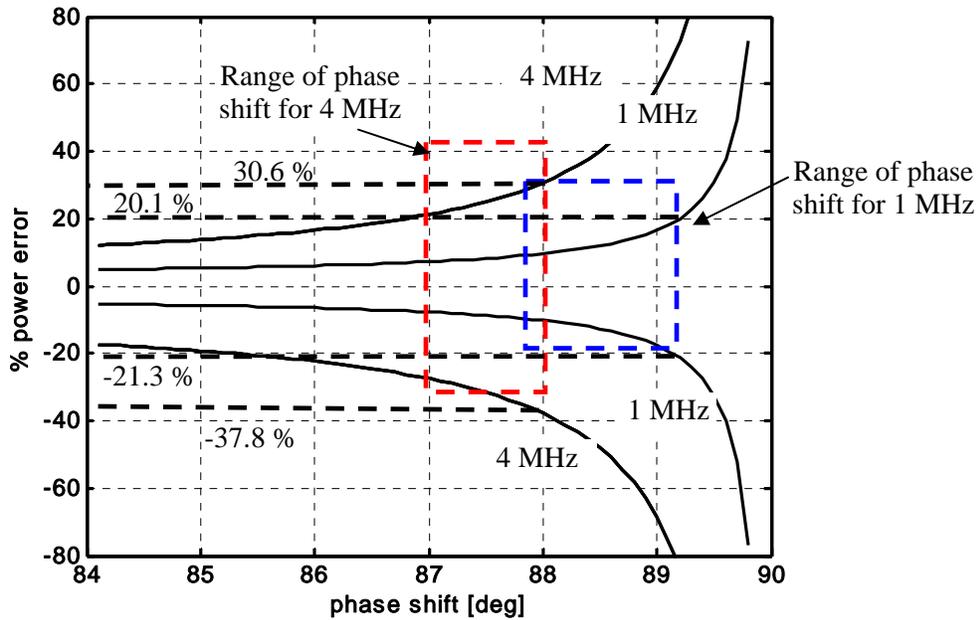


Figure 3-31 Percentage power error vs. phase shift between current through primary coils and voltage across secondary coils for 1 MHz and 4 MHz, considering total magnitude error and total phase error. Range of phase shift for 1 MHz and 4 MHz are indicated.

The maximum measurement error range is -21.3 % to +20.1 % for 1 MHz and -37.8 % to +30.6 % for 4 MHz in their respective range of phase shift as indicated in Fig. 3-31. Since Fig. 3-30 shows the error without considering the error involved in measurement, when measurement error is included, the total error will be increased by their respective amounts for 1 MHz and 4 MHz. Figure 3-32 shows the percentage power error vs. peak-to-peak flux density for (a) $f = 1$ MHz and (b) $f = 4$ MHz, considering measurement error discussed in section 3.4. The maximum measurement error range of -21.3 % to +20.1 % for 1 MHz is added to every data point in Fig. 3-30(a) to obtain Fig. 3-32(a). The maximum measurement error range of -37.8 % to +30.6 % for 4 MHz is added to every data point in Fig. 3-30(d) to obtain Fig. 3-32(b). Hence, the maximum error range of the model in predicting core loss is between -85.9 % to 63.7 % for a peak-to-peak flux density in the range of 5 mT to 50 mT, DC magnetic field intensity between 0 A/m to

1780 A/m at a temperature range of 26 °C to 70 °C, inclusive of the possible errors from measurement.

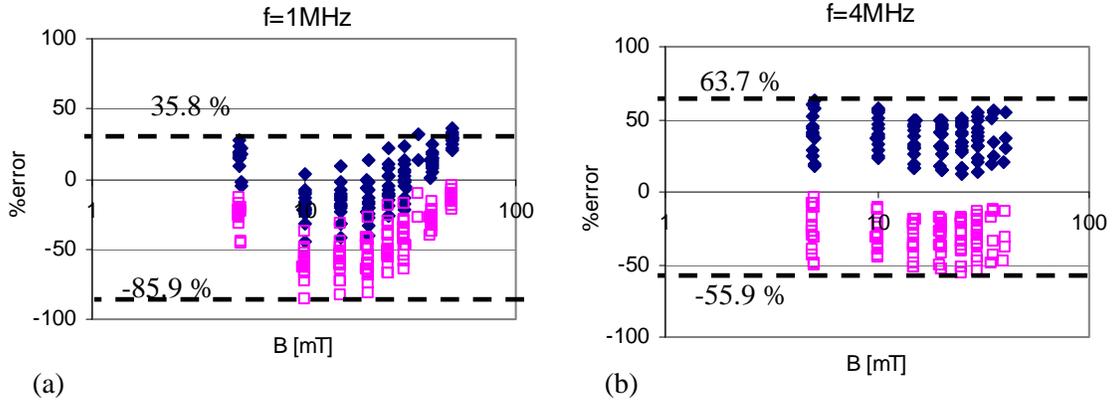


Figure 3-32 Percentage power error vs. peak-to-peak flux density, B for (a) $f = 1 \text{ MHz}$ and (b) $f = 4 \text{ MHz}$, considering measurement error discussed in section 3.4.

If temperature and I_{DC} dependence on the Steinmetz exponents, α and β , are not considered, the ratio of the estimated power using a constant Steinmetz exponent to actual power due to α or β alone can be expressed as:

$$ratio(\alpha) = \frac{f^{\alpha(\text{mean})}}{f^{\alpha(I_{DC}, T)}} \quad (3-40)$$

$$ratio(\beta) = \frac{B_m^{\beta(\text{mean})}}{B_m^{\beta(I_{DC}, T)}} \times 100\% \quad (3-41)$$

For $\pm 17.5 \%$ error in α , $ratio(\alpha)$ ranges between 0.0266 and 37.6, which implies that the power loss estimated using a constant α can be 37.6 times larger or smaller than the actual power loss. For a $\pm 5 \%$ error in β , $ratio(\beta)$ ranges between 0.577 and 1.733. If both α or β are considered, the power loss estimated using a constant α and β can be 65 times larger or smaller than the actual power loss. This clearly shows the necessity to express the Steinmetz exponents as a function of temperature and I_{DC} as opposed to assuming them as constants.

In summary, core loss is modeled using Steinmetz equation for frequencies between 1 to 4 MHz, peak-to-peak flux density between 5 mT to 50 mT and magnetic flux intensity, H , between 0 A/m to 1780 A/m. Temperature and DC current dependence are included in the model to describe their impact on core loss. The error range between the model and experimental result is between -85.9 % to 63.7 %.

3.6 Electrical Characterization of Conductive Paste

Series resistance of the inductor is an important parameter in power inductor design. In our fabrication process, we will be using a commercial Ag/Pt paste, also purchased from Electrosience Labs [28], to form printed conductors. To measure the resistivity of the Ag/Pt conductors, meander patterns are being screen-printed on 625 μ m thick alumina substrates and subsequently sintered using the sintering profile shown in Fig. 3-33. Fig. 3-34(a) shows the meander shaped conductor paste, screen printed on the alumina substrate. Fig. 3-34(b) shows the magnified cross-sectional view of the conductor patterns. The series DC resistance of the meander structure is measured and the resistance measurement results are summarized in Table 3-11.

The average estimated width of the Ag paste is 560 μ m and the estimated thickness is 62 μ m. Two approximation methods are used to estimate the cross-sectional area of the screen-printed conductor paste after sintering. The first method is to use a triangle to approximate the cross-sectional shape of the printed conductor and the second method is to approximate it as a segment of a circle as illustrated in Fig. 3-35. Using the equation:

$$\sigma = \frac{1}{A(R/l)} \quad (3-42)$$

where

A : cross-sectional area of the conductor

R : resistance of conductor

l : length of conductor

the conductivity of the screen-printed Ag paste can be calculated. Table 3-12 summarises the results obtained.

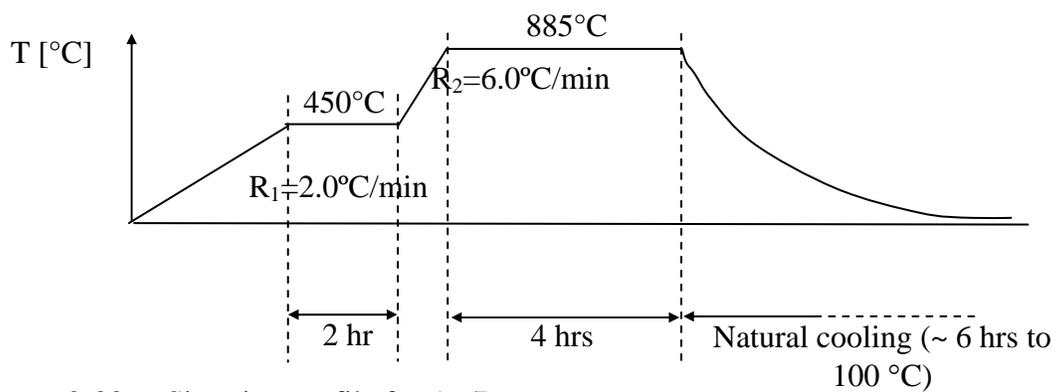


Figure 3-33 Sintering profile for Ag/Pt paste.

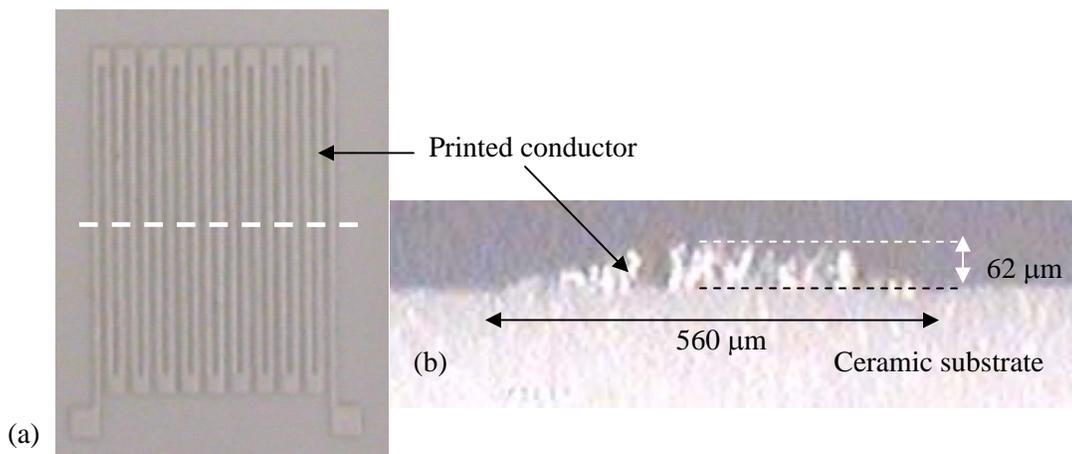


Figure 3-34 Cross-sectional view of the inductors (a) L_1 and (b) L_2 .

Table 3-11 Resistance Measurement Of Screen-Printed Conductors

Substrate	alumina
Line width [mm]	0.6
Length [mm]	500
R [Ω]	1.42
R/l [Ω/m]	2.84
R/sq [$m\Omega/sq$]	1.704

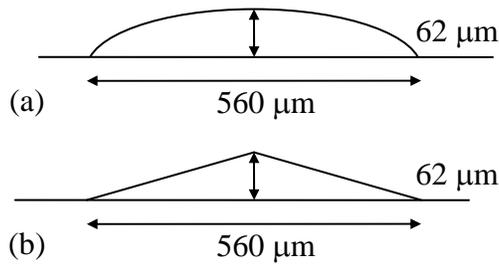


Figure 3-35 Cross-sectional area approximation of screen-printed Ag/Pt conductor using (a) segment of a circle and (b) triangle.

Table 3-12 Estimated Conductivity Of The Screen-Printed Conductor Paste Using The Two Methods.

	Area [mm^2]	σ [S/m]
Triangle	1.74×10^{-2}	2.02×10^7
Segment of circle	2.35×10^{-2}	1.50×10^7

As an average, the conductivity, σ , of the post sintered conductor paste is approximated to be $\sigma = 1.7 \times 10^7$ S/m. From here on, we use this value for our subsequent calculations.

3.7 Summary

In this chapter, characterization of the materials involved in magnetic integration using LTCC technology has been performed. The permittivity of the LTCC ferrite tape is estimated to be 13. In core loss measurement, sources of the various errors in the core loss measurement circuit have been identified, analyzed and quantified. The choice of the components for the core loss measurement circuit has been discussed and the design of the core and the windings has been formulated. Finally, the operational influence on electromagnetic characteristics of LTCC magnetic material is studied and a model based on Steinmetz equation with temperature and DC current dependence is developed. Core loss is modeled using Steinmetz equation for frequency between 1 to 4 MHz, peak-to-peak flux density between 5 mT to 50 mT and magnetic flux intensity, H , between 0 A/m to 1780 A/m. Temperature and DC current dependence are included in the model to describe their impact on core loss. The error range between the model and experimental result is between -85.9 % to 63.7 %.

Chapter 4. LTCC Chip Inductor Development

4.1 Overview

This chapter will discuss about the LTCC chip inductor development. The chapter will start with a comparison of the various inductor geometries found in literature, followed by geometry selection for high current application. The inductance change with DC current application for the chosen geometry and the impact of varying inductance on circuit performance are then discussed. The impact of conductor cross-sectional shape for the chosen geometry will be discussed and the desired conductor cross-sectional shape for high current and high frequency application will be selected. The power inductor fabrication procedure to obtain the desired geometry will be elaborated. Based on the selected geometry and fabrication procedure, parametric variation of the inductor's physical geometry is performed and an empirical inductance model is developed. The chapter will be concluded by an inductor design procedure.

4.2 Geometry Selection for Integratable Chip Inductor

4.2.1 Comparison of Various Geometries of Planar Inductor

The integrated inductors can take various forms and geometries. This section will compare the various geometries found in literature and the most suitable geometry will be selected for our application.

4.2.1.1 Toroidal coil inductor

A toroidal coil [21, 101, 102] is a common geometry for an inductor by virtue of its symmetry. In a toroidal coil inductor, the conductors wrap around the magnetic material, which is embedded in the substrate. In this geometry, via formation is necessary for an integrated inductor to connect the conductors above and below the magnetic material. The inductance can be controlled by the number of turns and the permeability of the magnetic core selected. This geometry can be chosen if the electrodes have to be close to each other. By virtue of the resultant higher resistance due to the length of conductor which wrap around the magnetic core, this geometry may not be the best option for high current application. Fig. 4-1 shows some toroidal coil inductors on LTCC NiCuZn ferrite substrate [21].

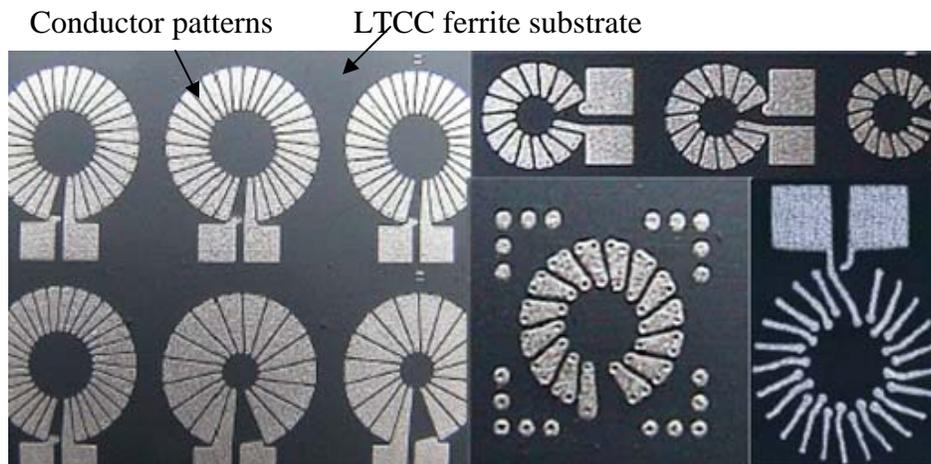


Figure 4-1 Toroidal coils on LTCC NiCuZn ferrite substrate [21].

4.2.1.2 Solenoid inductor

The solenoid inductor [31, 32, 103, 104] is another common geometry. The solenoid inductor comprises windings wrapped around a magnetic core. The windings form the

top and bottom layers and the magnetic material is sandwiched between the windings. Similar to the toroidal coil geometry, via formation is necessary for an integrated inductor to connect the conductors above and below the magnetic material. A serious disadvantage of this type of inductor is that the magnetic circuit does not close through the magnetic material, leading to inefficient use of material and other disadvantages that confine this to low power applications. This geometry can be selected if the electrodes are far from each other. Fig. 4-2 show some solenoid micro-transformers and micro-inductors found in [31, 32, 103, 104].

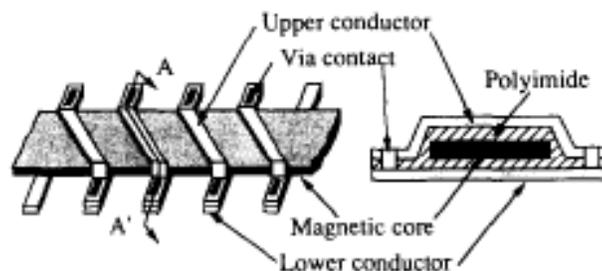


Figure 4-2 Planar inductor with micromachined NiFe magnetic bar [104].

4.2.1.3 Racetrack or spiral inductor

As opposed to the toroidal coil or solenoid inductor, which the windings wrap around the core, the racetrack [29, 105] and spiral [106-110] inductor has the core wrapped around the winding. Here, the magnetic circuit closes through the magnetic core, leading to much better use of material. For the pot-core structure, the inductor winding is relatively long. It is suitable for making inductors with high inductance, however, it is also not the best option for high current applications. Fig. 4-3 shows an on-chip racetrack winding inductor using NiFe magnetic core [105]. Fig. 4-4 shows an air-core vertical stacked spiral inductor for RFIC applications [106].

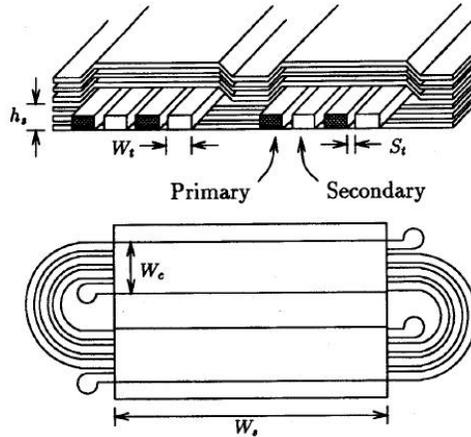


Figure 4-3 On-chip racetrack winding inductor using NiFe magnetic core [105].



Figure 4-4 Vertical stacked spiral inductor for RFIC applications [106].

4.2.1.4 Meander inductor

Another possible geometry is the meander winding geometry [47, 111]. In this geometry, the conductor winding is sandwiched between two layers of magnetic material. In this configuration, the magnetic core surrounds each strand of conductor. As a result, there is little or no coupling between turns. Hence, the inductance obtained with this kind

of structure does not depend on winding arrangement but rather on its length. Fig. 4-5 shows a thick film meander inductor [47]. The length of the winding will again contribute appreciably to the conductive losses, making this less suitable for high current applications.

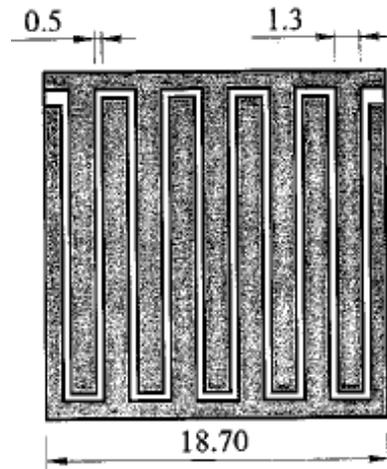


Figure 4-5 Thick film meander inductor [47].

4.2.1.5 Short winding inductor

The short winding inductor typically comprises a single winding with substantially large cross-sectional area, with the magnetic core wrapped around it. This kind of geometry is the most suitable for high current applications. However, the inductance achievable may be low. The inductance of this type of inductor is determined by the length of the conductor and the properties of the magnetic material wrapped around it. Fig. 4-6 shows a V-groove inductor embedded in the silicon [112]. Figure 4-7 shows the cross-sectional diagram of a thick film planar inductor [47].

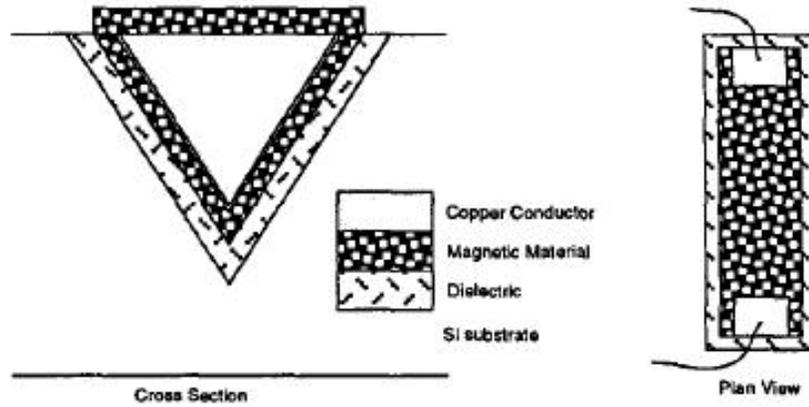


Figure 4-6 V-groove inductor embedded in silicon [112].

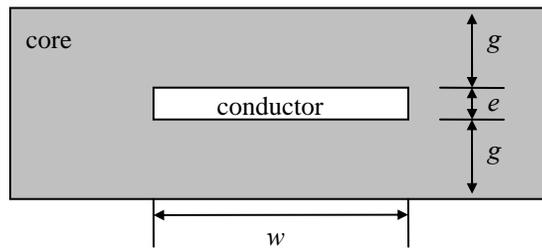


Figure 4-7 Cross-sectional diagram of thick film planar inductor [47].

4.2.1.6 Summary

Based on the above inductor geometries, the short winding inductor with magnetic core wrapping the conductor gives the flexibility in varying the conductor's cross-sectional area. Hence, it is a suitable candidate for achieving low DC resistance and high current capability.

4.2.2 Concept of Varying Inductance with Bias for Chosen Geometry

By virtue of the absence of a discrete air-gap for the inductor shown in Fig. 4-6 and Fig. 4-7, any change in the relative permeability of the magnetic core as a result of pre-

magnetization can result in a change in inductance as illustrated in Fig. 4-8. L_2 is a non-linear inductor and L_1 is a linear inductor. This is an effect that relates to both the relative permeability and the average magnetic path length and will be discussed later in this chapter.

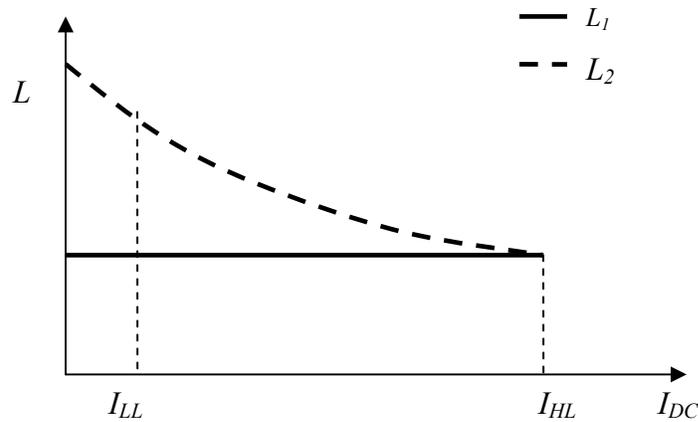


Figure 4-8 Illustration of changing inductance with DC current for non-linear inductor L_2 in comparison with a linear inductor L_1 with constant inductance with DC current.

4.2.3 Impact of Varying Inductance on Circuit Performance

The light load efficiency of a converter is an important factor in extending battery life. Sun et al. [113] used a non-linear inductor to improve the DCM efficiency for laptop CPU voltage regulator. A saturable E-I core with stepped center leg is used to realize the non-linear inductor. The non-linear inductor has a large inductance at CPU sleep state (light load) and has a small inductance at CPU active state (heavy load).

Using a synchronous buck converter as an example, the impact of varying filter inductance on circuit performance will be discussed. Fig. 4-9 shows the circuit diagram of a buck converter. With a larger inductance at light load, the inductor current ripple will be smaller at a low DC current. With a smaller ripple current, the RMS current

through the switches will be decreased, which can help decrease losses in the switches. Fig. 4-10 shows the inductor current ripple at heavy load (Δi_2) and at light load (Δi_1) as a result of the presence of a non-linear filter inductor. With a smaller inductor current ripple, the RMS current through the top switch, I_{top} , as in Fig. 4-9, will be decreased. Fig. 4-11(a) shows the current waveform of the top switch if a small filter inductance is used. Fig. 4-11(b) shows that when a large filter inductance is used. The switch current waveform can be described by the following equation (4-1) [114].

$$I_{top,rms} = I\sqrt{D}\sqrt{1 + \frac{1}{3}\left(\frac{\Delta i}{I}\right)^2} \quad (4-1)$$

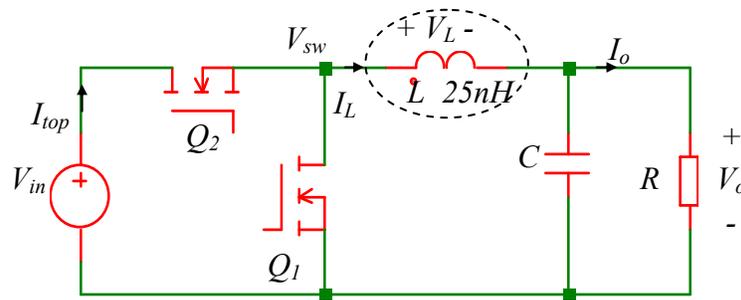


Figure 4-9 Buck converter circuit diagram.

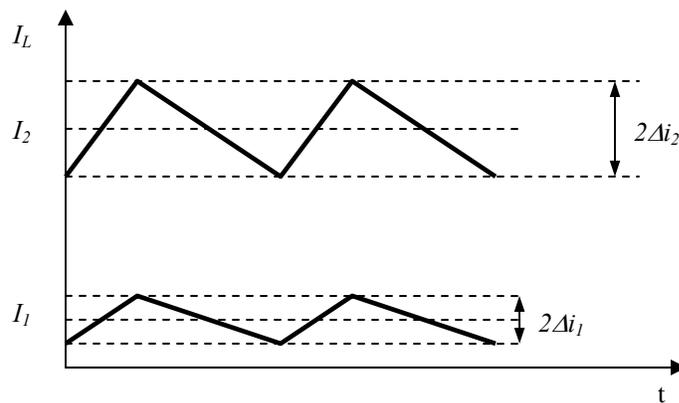


Figure 4-10 Inductor current when inductance is higher at light load and lower at heavy load.

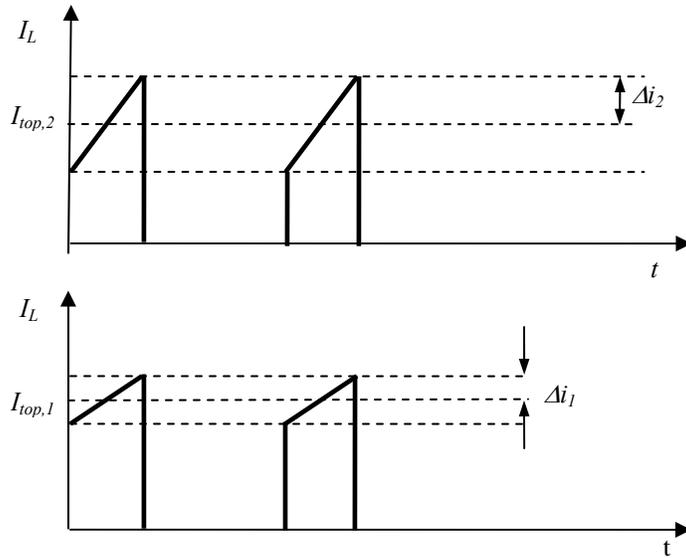


Figure 4-11 Current waveform of the top switch for (a) small filter inductance and (b) large filter inductance.

It is clear that when the ripple current Δi is small, the RMS current of the switch will decrease. This helps to decrease losses in the switches, particularly at light load. Figure 4-12 shows the comparison of power stage efficiency, η , vs. DC current for linear inductor L_1 and non-linear inductor L_2 . When the non-linear inductor, L_2 , is used, the light load efficiency will become higher.

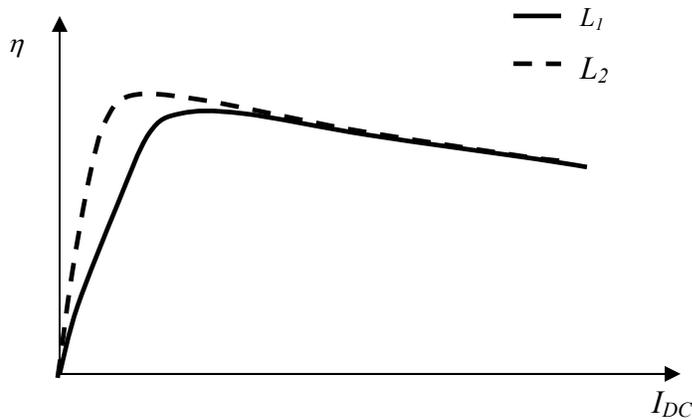


Figure 4-12 Power stage efficiency, η , vs. DC current for linear inductor L_1 and non-linear inductor L_2 .

4.3 Conductor Cross-Sectional Shape Study for Chosen Geometry

The conventional way [115, 116] of screen-printing conductor paste on LTCC tapes yield elongated conductors with sharp edges. This is by virtue of the way the conductor paste is printed, and is related to the physics of viscous fluids printed on a surface [117, 118]. Due to electromagnetic considerations, this is found to be detrimental from the power loss point of view, especially at high operating frequencies.

As discussed in chapter 2, however, the process for manufacturing the inductors can be modified to have alternative shapes, so that the implications of these different shapes have to be studied. In this section, the effect of an elongated conductor cross-sectional shape is evaluated. Different conductor cross-sectional shapes are studied and comparison are made in terms of power loss in the presence of magnetic material around the conductor. An experimental verification is made by comparing the performance of two types of filter inductors, one with elongated cross-sectional shape fabricated using the conventional conductor screen printing method and the second one is a conductor with rectangular cross-sectional shape, fabricated using a modified method (refer Chapter 2), that gives a cross-sectional shape close to the desired capsule shape, in a prototype 5V – to – 1 V Buck converter. A comparison in system performance is made.

4.3.1 Simulation of Conductors with Various Cross-Sectional Shapes

In order to maintain the low profile of embedded passives fabricated using LTCC technology, alternative conductor shapes chosen for comparison are the rectangular and the capsule shaped conductor cross-sectional shapes, rather than squares and circles.

Figure 4-13 shows the dimensions of the shapes being compared. The cross-sectional areas of the shapes are kept constant at 0.1 mm^2 . Conductors with diamond-shaped cross-section are simulated in place of the almond-shaped conductors, which are typically formed by screen printing, as shown in Fig. 2-19.

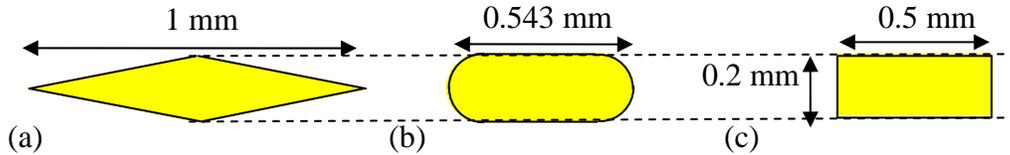


Figure 4-13 Comparison of conductor cross-sectional shapes, (a) diamond, (b) capsule, and (c) rectangular, for a cross-sectional area of 0.1 mm^2 .

Simulation is performed using Ansoft Maxwell 2D. The conductor's conductivity used in the simulation is $1.7 \times 10^7 \text{ S/m}$, which is an experimentally determined value from sintered Ag/Pt paste on alumina substrates, as discussed in Chapter 3 of this dissertation. Simulation is performed for a conductor surrounded by air and a conductor surrounded by magnetic material of relative permeability 60 and dielectric constant of 13. A magnetic material of this relative permeability is preferably used for applications where the frequency exceeds 1 MHz, due to its more favorable characteristics in the frequency range, as compared to LTCC materials with a higher relative permeability.

4.3.1.1 Conductors in Air

Simulation is performed for conductors with capsule, rectangular and diamond cross-sectional shapes. Fig. 4-14 shows the 2-D current density distribution for the three types of conductor cross-sectional shapes. The simulation frequency is 4 MHz and the current has an amplitude of 1 A.

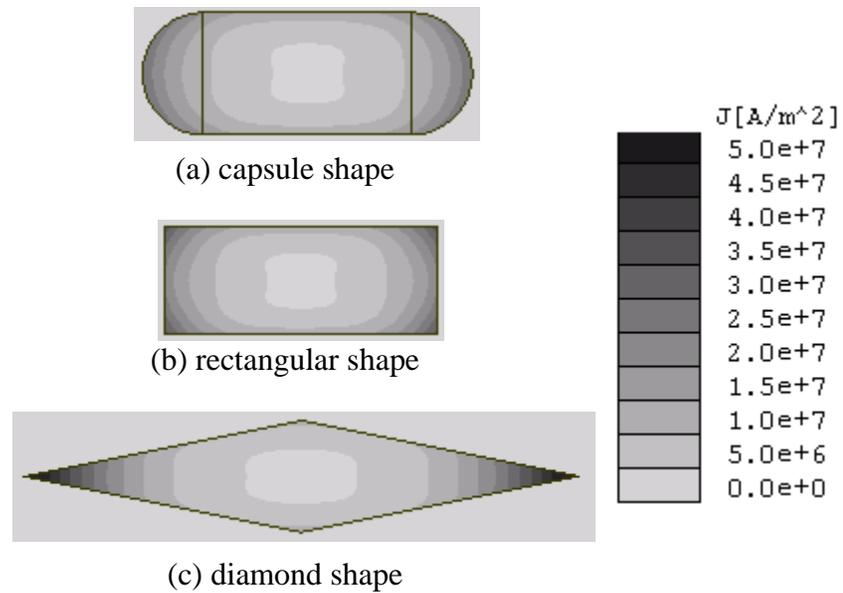


Figure 4-14 2-D current density distribution for (a) capsule shaped, (b) rectangular shaped and (c) diamond shaped conductors in air. Frequency = 4 MHz.

It is clearly evident that there is a concentration of current at the sides, particularly at the edges with small angles. This will contribute to additional conduction losses especially as frequency increases. Conduction power loss per unit length, according to Ohm's law, is given by:

$$\frac{P}{l} = \int_A \frac{\vec{J}}{\sigma} \cdot \vec{J} dA \quad (4-2)$$

where

\vec{J} : current density vector [A/m²]

σ : conductivity [S/m]

A : cross-sectional area of conductor [m²]

P : conduction power loss [W]

l : length of conductor [m]

To compare the difference in the current density level, the current density is plotted along the dotted line across the capsule and diamond shaped conductors (see Fig. 4-15), as the maximum current density for both structures lie along this line. Fig. 4-15 shows the 1-D current density plot along the red dotted line for the capsule and the diamond shaped conductors in air. The current density at the sharp corners of the diamond shaped conductor is approximately double that of the capsule shaped conductor. Fig. 4-16 shows the comparison of the power loss in the conductors as a function of frequency. The conductor with diamond cross-sectional shape demonstrated significantly (20 %) higher conduction losses at 4 MHz, than the rectangular and capsule shaped conductors.

When the conductor is surrounded by magnetic material, the current segregation at the sharp corners is aggravated, which will be illustrated in the next section.

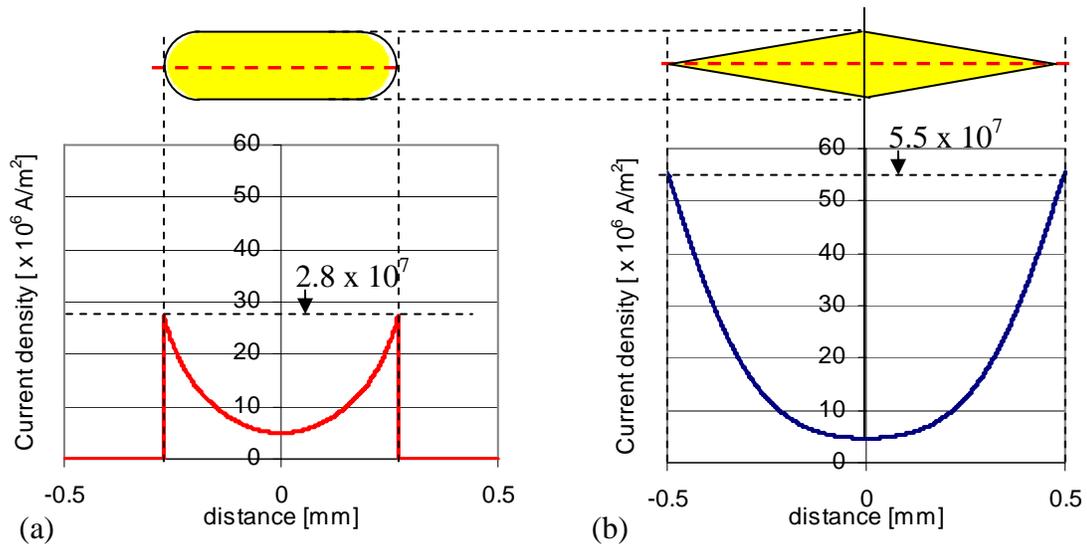


Figure 4-15 1-D current density along dotted line for capsule and diamond conductor cross-sectional shapes in air. Frequency = 4 MHz.

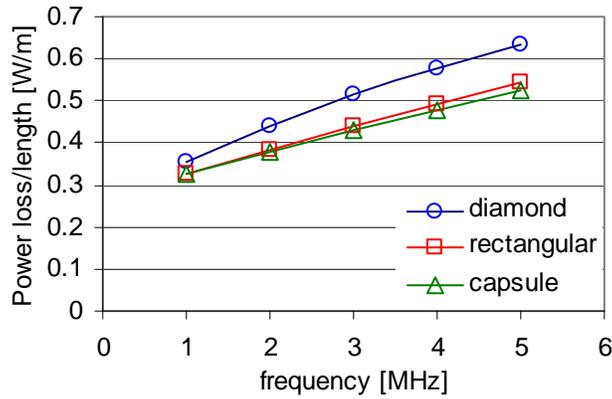


Figure 4-16 Conduction power loss per unit length for various conductor shapes in air.

4.3.1.2 Conductors in Magnetic Medium

In the previous section, it is observed that conductors with diamond cross-sectional shape results in larger conduction losses especially at elevated frequencies. In the development of power inductors using LTCC technology, it is necessary to look into the impact of conductor cross-sectional shapes in a magnetic medium. The losses in the inductor originate from the DC current losses (average current $\times R_{DC}$), the AC current losses (due to ripple) and the core losses. The conductor cross-sectional shapes under comparison are the diamond shape, rectangular shape and capsule shape. For a fair comparison, the conductor cross-sectional areas, core material and core volume are kept constant. The simulation is conducted at 4 MHz and the AC current is 1 A. Core loss is simulated using the Steinmetz exponents for the ESL-40010 LTCC⁴ material given in equation (4-3).

$$P_v = 1.32 \times 10^{-5} f^{1.255} B^{2.06} \quad (4-3)$$

⁴ ESL-40010 LTCC ferrite tape is the low permeability tape ($\mu_r = 60$) from the Electroscience Labs.

Figure 4-17 shows the 1-D current density plot along the dotted line for the capsule and the diamond shaped conductors surrounded by magnetic material of $\mu_r = 60$ and $\epsilon_r = 13$. Fig. 4-18 shows the conduction power loss per unit length vs. frequency for the three types of conductor cross-sectional shapes surrounded by magnetic material of $\mu_r = 60$ and $\epsilon_r = 13$. Fig. 4-19 shows the core loss per unit length vs. frequency for conductors surrounded by magnetic core of $\mu_r = 60$.

It is clear that when a conductor is surrounded by a magnetic medium, current segregation is aggravated. In Fig. 4-17, the current density at the sharp corners of the diamond shaped conductor is an order of magnitude higher than that of the capsule shaped conductor in magnetic medium. From Fig. 4-18, the conduction power loss in an diamond shaped conductor is double that of the rectangular or capsule shaped conductor at a frequency of 5 MHz. Fig. 4-19 shows the core loss comparison for the three conductors with different cross-sectional shapes. The core loss for the inductor with diamond shaped conductor is 25 % higher than inductors with rectangular or capsule shaped conductor. Table 4-1 tabulates the energy storage and loss comparison for conductors with diamond, rectangular and capsule cross-sectional shapes. The energy storage (which directly translates to inductance) for the inductor with diamond shaped conductor is lower than that of the inductors with rectangular and capsule shaped conductors. This implies that to obtain the same inductance, the inductor with diamond shaped conductor needs to be of longer length. This indicates even higher losses per unit inductance. Hence, it is clear that from both the conduction and core loss point of view, inductors with diamond cross-sectional shape result in higher losses compared with capsule and rectangular shape.

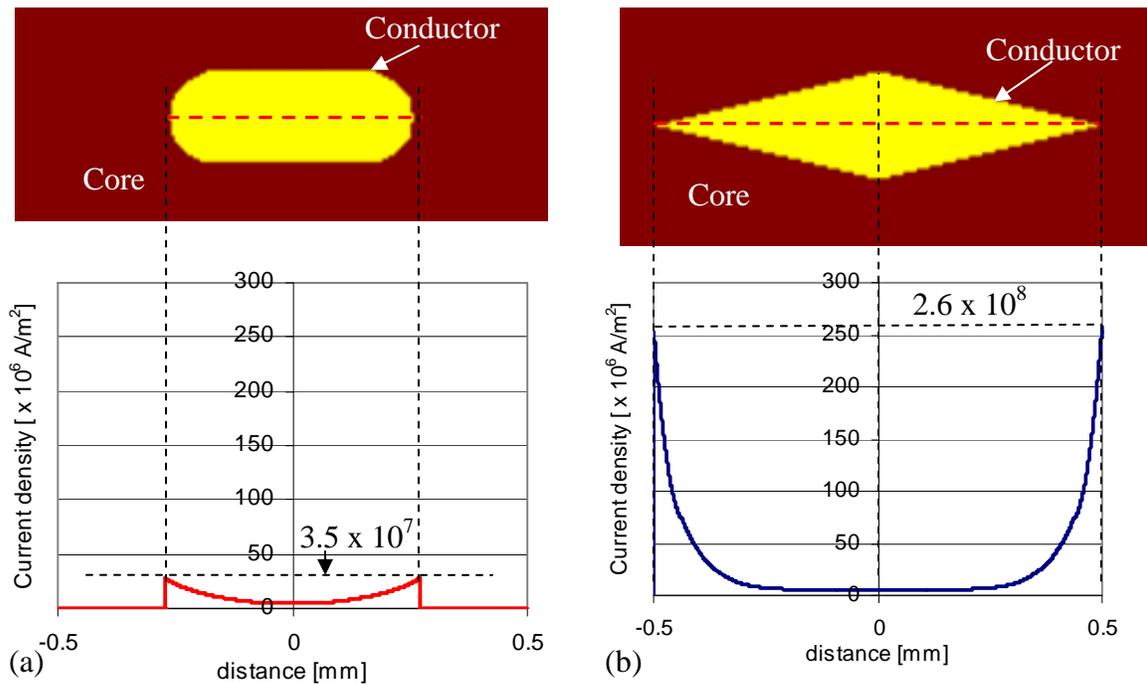


Figure 4-17 1-D current density along dotted line for (a) capsule and (b) diamond conductor cross-sectional shapes, surrounded by magnetic material. Frequency = 4 MHz.

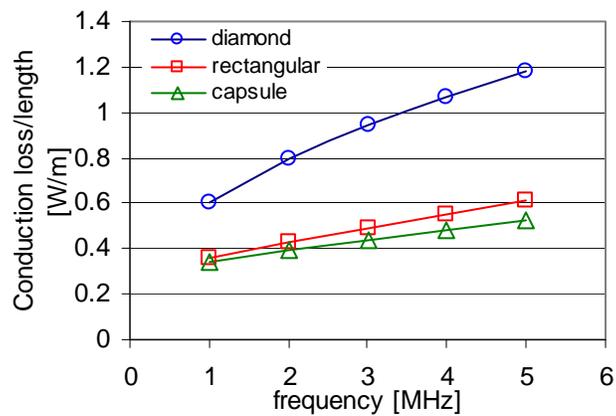


Figure 4-18 Conduction power loss per unit length for conductors of various shapes surrounded by magnetic core of $\mu_r = 60$ and $\epsilon_r = 13$.

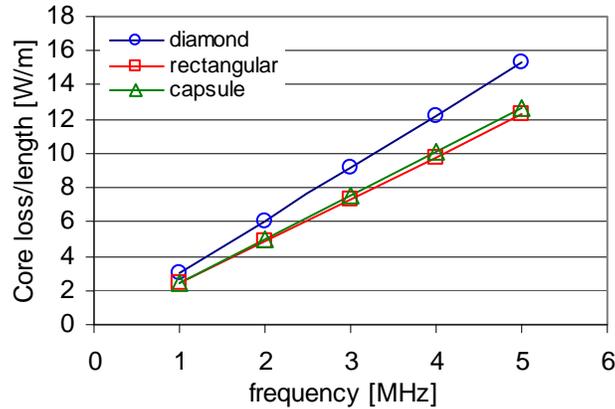


Figure 4-19 Core loss per unit length for conductors of various shapes surrounded by magnetic core of $\mu_r = 60$ and $\epsilon_r = 13$.

Table 4-1 Loss comparison for conductors with diamond, rectangular and capsule cross-sectional shapes at $f = 4$ MHz and $I = 1$ A.

	Energy stored [$\mu\text{J}/\text{m}$]	Conduction loss [W/m]	Core loss [W/m]	Total loss [W/m]
diamond	2.97	1.07	12.21	13.28
rectangular	3.50	0.55	9.78	10.33
capsule	3.56	0.48	10.06	10.54

4.3.1.3 Final Selection of Generic Geometry

In the previous section, it is observed that in order to reduce the both conduction and core losses in magnetic components using LTCC tapes, it is necessary to change the conductor cross-sectional shape by processing means, to reduce or eliminate sharp edges. Due to the difficulty and complexity of obtaining conductors of capsule cross-sectional shape, we will be looking into obtaining rectangular conductor cross-sectional shapes. As reported in the previous two sections 4.3.1.1 and 4.3.1.2, rectangular-shaped

conductors yield slightly higher conduction losses than capsule shaped conductors, however, the improvement in losses is significantly lower than a diamond shaped conductor.

In summary, conductors with elongated diamond/almond cross-sectional shape are undesirable for high frequency applications from the conduction loss point of view. The overall power loss becomes greater when the conductor is surrounded by magnetic material. Hence, it is desirable to alter the conventional method of screen printing conductor paste on LTCC green tape to obtain a rectangular conductor cross-sectional shape (see fabrication procedure in Chapter 2) for applications in which power loss is to be minimized. In addition, from the point of view of footprint occupied by the conductor, conductors with rectangular conductor cross-section offer the potential to obtain a much smaller footprint compared to conductors with almond/diamond cross-sectional shapes.

4.3.2 Experimental Study

From the previous section, simulations have shown that inductors with rectangular conductor cross-sectional shape have lower losses than that of diamond/almond conductor cross-sectional shape. In this section, the higher power loss of having an almond-shaped conductor cross-section is experimentally verified. In this experiment, four inductors with almond conductor cross-sectional shape and four with rectangular cross-sectional shape are fabricated. The fabrication procedures for both types of inductors are as described in Chapter 2. Figure 4-20 shows the cross-sectional view of LTCC inductors with (a) rectangular and (b) almond-shaped cross-sections. The inductors were tested in a prototype 5 V - to - 1.1 V buck converter operating at 4 MHz.

Figure 4-21 shows the photograph of the experimental setup for circuit evaluation. The inductor temperature is monitored using a K-type thermocouple dipped in thermal paste and attached to the back of the inductor. The active devices are cooled using a heat sink placed on top of the chip and a fan placed beside the circuit board. To prevent the fan from interfering with the temperature measurements, a cylindrical column is placed over the inductor to minimize the effect of the fan on the temperature of the inductor as shown in Fig. 4-22.

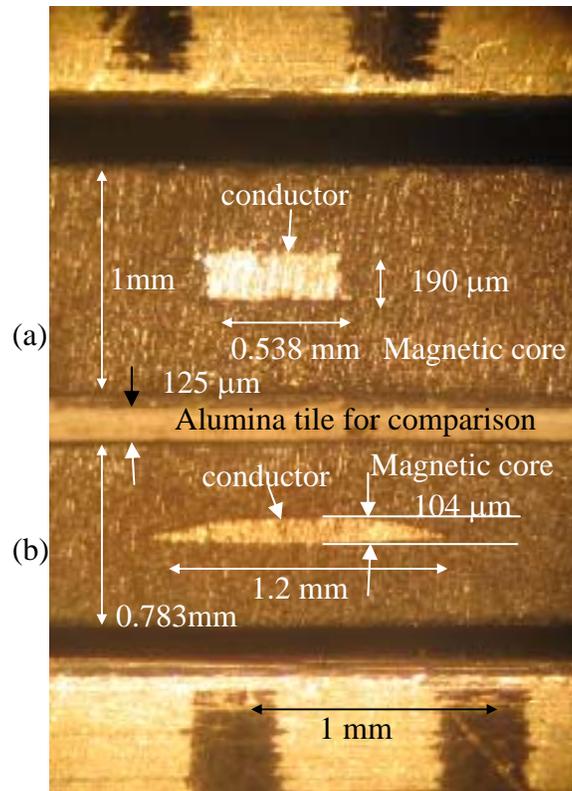


Figure 4-20 Cross-sectional view of LTCC inductors with (a) rectangular and (b) almond cross-sectional shape.

Figure 4-23 shows the inductor current and voltage waveforms. The inductance is calculated using the ratio of the voltage across the inductor when the top switch (Q_2 of Fig. 4-9) is off and the current slew rate at the decreasing part of the current waveform, as illustrated by region A. The inductance, L_1 , comprises the inductance of the copper trace

on the PCB, the copper leads connecting the inductor to the PCB and the inductor's actual inductance. To find the inductance contribution of the PCB copper trace and the copper leads, L_2 , a wide piece of copper is soldered in place of the inductor. The inductance contributed by the PCB copper trace and the copper leads is deducted from inductance L_1 to obtain the actual inductance of the inductor. The parasitic inductance in the switches and the capacitors has a negligible contribution to the inductance measurement mentioned above.

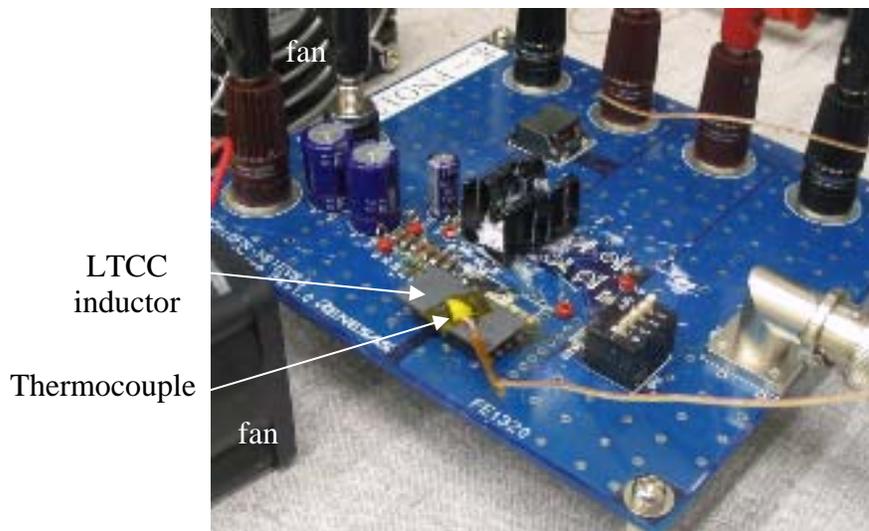


Figure 4-21 LTCC inductor tested on prototype Buck converter. The temperature of the inductor is measured using a K-type thermocouple attached to the back of the inductor.

Figure 4-24 shows the inductance and the temperature rise comparison for the inductors with rectangular and almond-shaped conductor cross-sections at full load ($I_{DC} = 5A$). Inductors whose conductors have almond-shaped cross-sections generally have a larger temperature rise compared with inductors with rectangular-shaped conductor cross-sections. The temperature rises are $19\text{ }^{\circ}\text{C}$ and $27\text{ }^{\circ}\text{C}$ at full load for rectangular and elongated almond-shaped conductor cross-sections, respectively. Since the circuit operating conditions are the same for both inductors, the higher temperature rise of the

inductor with almond-shaped conductor cross-sections indicates higher losses in the inductor.



Figure 4-22 Cylindrical column placed over the inductor to minimize the effect of the fan on temperature measurements.

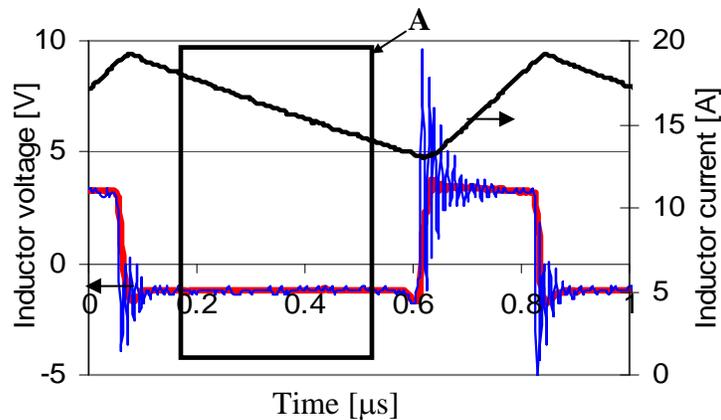


Figure 4-23 Inductor voltage and current waveforms.

In summary, the screen printing technique of dispensing conductors on LTCC ferrite tapes produces conductors with almond conductor cross-sectional shape. The sharp edges of the almond-shaped conductors result in higher losses in the inductor compared with an inductor with rectangular cross-sectional shape, as verified experimentally.

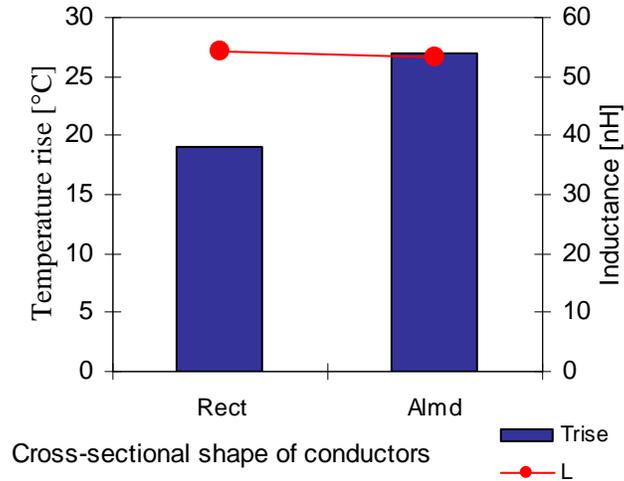


Figure 4-24 Inductance and temperature rise comparison for the rectangular and almond conductor cross-sectional shapes at full load ($I_{DC} = 5A$).

4.4 Circuit Specifications for Chip Inductor

The inductors are tested in a prototype 5 V - to - 1.1 V buck converter (see Fig. 4-9) operating at a switching frequency of 4 MHz. The devices used are integrated in a multichip module, DrMOS from Renesas [119]. The integrated top MOSFET (Q_2) is HAT2168 and the bottom MOSFET (Q_1) is HAT2165. The full load current is 12.5 A. The input voltage of the gate drive is 5 V, which is provided by the Agilent E3631A. The pulse width modulation (PWM) input is provided by means of a 20 MHz Agilent function generator 33220A. The power supply for the power stage is provided by the Lambda UP6-132 DC power supply. Four Fluke 45 dual display digital multi-meters are used to measure the input and output voltages as well as currents.

A shunt is connected between the power supply and the input node of the buck converter circuit for the purpose of measuring the input current. Another shunt is connected between the output and the ground for measuring the output current. The

currents are obtained by measuring the voltages across the shunts using the digital multi-meters and dividing by the resistances of the shunts. The power stage efficiency is calculated using the following equation.

$$\eta = \frac{V_o \cdot I_o}{V_{in} \cdot I_{in}} \times 100\% \quad (4-4)$$

In the measurement of waveforms, a Tektronix TDS 5104 digital phosphor oscilloscope is used. The voltage probe used is the Tek P5050, with bandwidth of 500 MHz. The current waveform is measured using the CWT ultra mini Rogowski current transducer from Power Electronics Measurements Ltd.

4.5 Geometry of LTCC Chip Inductor for Model Development

The geometry of the chip planar inductor as discussed earlier comprises a conductor with rectangular cross-section enclosed by the magnetic core without a discrete air-gap. Fig. 4-25 shows the three-dimensional view of the planar chip inductor. The cross-sectional view of the inductor is shown in Fig. 4-7.

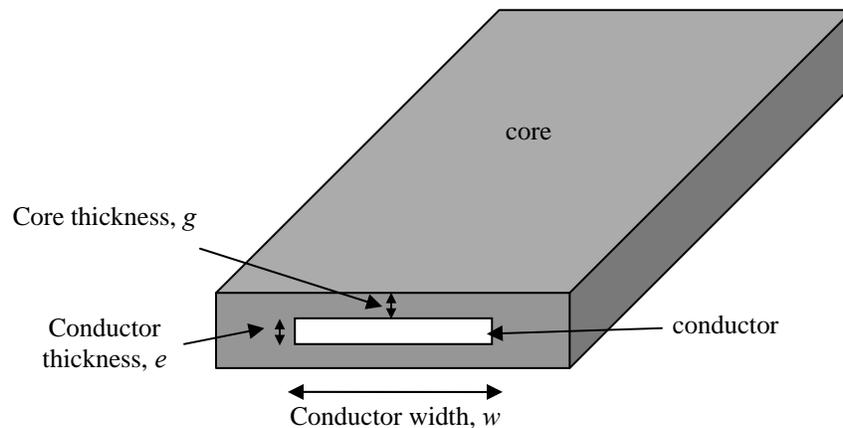


Figure 4-25 Three-dimensional view of LTCC planar inductor.

4.6 Parametric Variation of Inductor Geometry

The variation in permeability due to saturation and the resulting change in magnetic path length establish a complex relationship between the material properties, geometry, current and inductance. Yet, an adequate quantitative model for inductance variation does not exist. It was therefore decided to carry out geometry variation experiments to study the effect of the inductor geometry on the circuit performance, particularly the light load efficiency. The effect of varying the number of parallel conductors of the planar inductor and the conductor width on the overall efficiency of the converter, particularly the light load efficiency, are studied. This variation experiment can serve as a guide in designing the filter inductor according to the requirements and tradeoffs between light load efficiency and transient performance of the converter. It also serves to evaluate whether the LTCC processing and manufacturing of the inductor needs to be changed, since dimensions can influence temperature profiles, laminating pressures and warping during firing. For all the variation experiments, the full load inductance is kept constant, so that the inductor current ripple at full load is kept constant. This implies that the switching and gate driver losses are kept constant at full load. The effects of inductor geometry on light load efficiency are then compared.

4.6.1 Effect of Varying Conductor Width

In this set of experiments, the conductor width of a single conductor inductor is varied to study its effect on light load efficiency of the converter. The conductor width of the inductor is varied between 1 mm to 5 mm, with the dimensions defined as in Fig. 4-

26. The dashed line indicates the position of the embedded conductor of the inductor. Fig. 4-27 shows the cross-sectional view of the inductors with different conductor widths ranging from 1 mm to 5 mm. The fabrication procedure in section 2.4.7 as described in association with Fig. 2-20 is not affected.

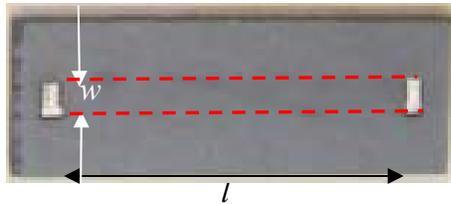


Figure 4-26 Dimensions of LTCC inductor.

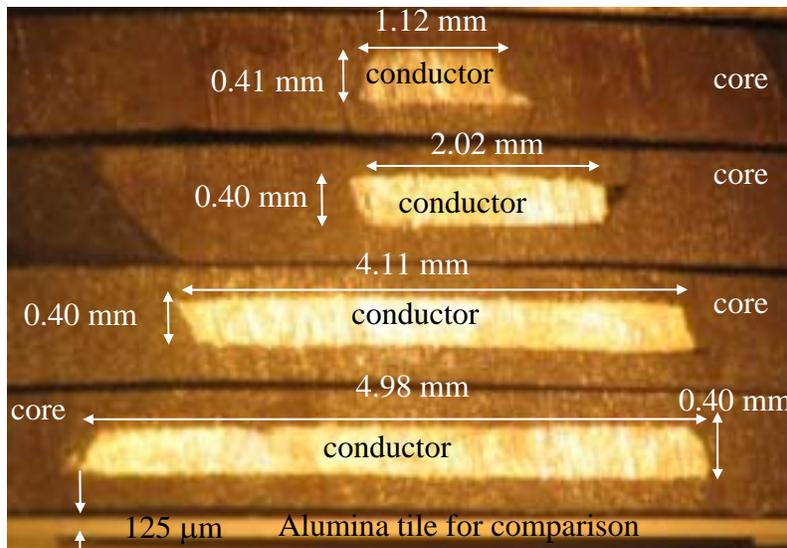


Figure 4-27 Cross-sectional view of LTCC inductors with conductor widths ranging from 1 mm to 5 mm.

Fig. 4-28 shows the change in inductance with output current for the various inductors with conductor widths ranging from 1mm to 5mm. It is observed that as inductor width decreases, the change in inductance with output current increases.

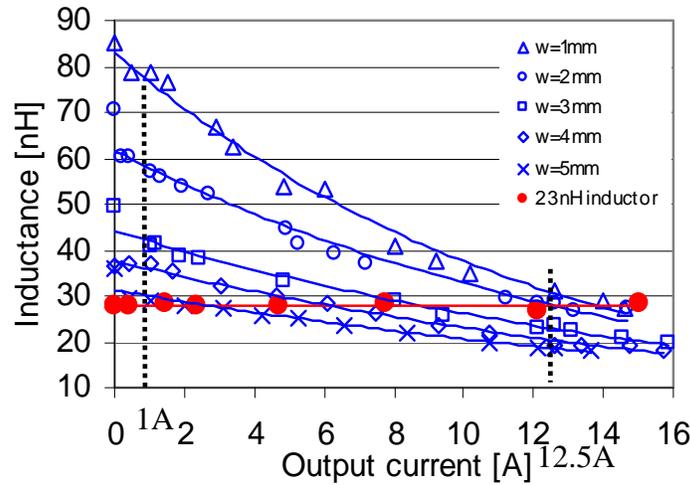
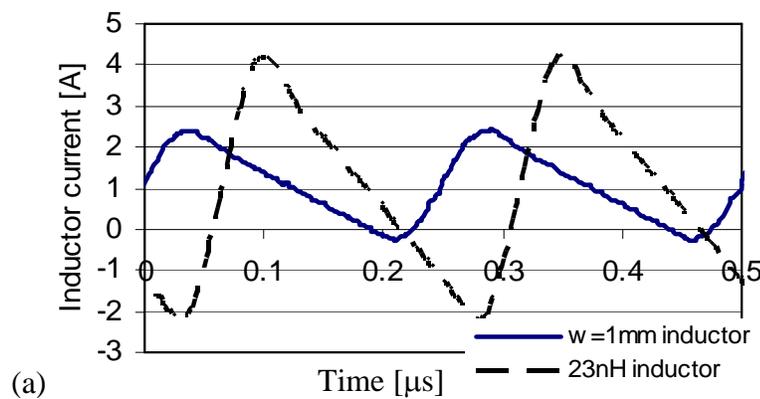


Figure 4-28 Change of inductance with output current.

Figure 4-29(a) shows the comparison of light load inductor current waveforms for LTCC inductor with a conductor width of 1 mm, and the two commercial 47 nH air-gapped inductors connected in parallel, named as 23 nH inductor as a benchmark. Fig. 4-29(b) shows the comparison of inductor current waveforms of the two inductors at a full load current of 12.5 A. It is clear that the current ripple associated with these two types of inductors at this current is similar.



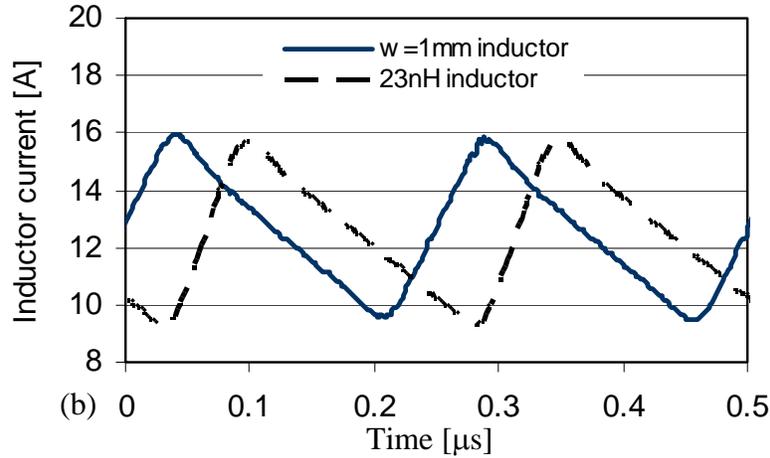


Figure 4-29 Inductor current waveforms comparison (a) at light load current of 1 A and (b) at full load current of 12.5 A, for LTCC inductor with conductor width 1 mm and commercial inductor of effective inductance 23 nH. $V_{in} = 5$ V, $V_o = 1.1$ V.

The substantial reduction in the inductor ripple current at light load is attributed to the higher inductance value of the LTCC inductor with conductor width, w , of 1 mm at light load. This results in an increase in light load efficiency of the converter, as evident in Fig. 4-30(a). At a light load current of 1 A, the efficiency can be improved by greater than 15 %. When the load current decreases to 0.5 A, the efficiency can be improved by greater than 30 %. Fig. 4-30(b) shows the heavy load efficiency comparison. At a full load current of 12.5 A, the difference in power stage efficiency is kept to within 2 %. Above this current, it is evident that the decreasing tendency of the efficiency for a conductor width of 5 mm differs from the other curves. We conclude that this is not due to increased inductor losses. It is to be noted here that the full load inductance for the inductor with conductor width 1mm (31 nH) is larger than that for the inductor with conductor width 5 mm (18.5 nH). This implies that the all important semiconductor switching losses in the circuit will be higher for the inductor with conductor width 5 mm and continue to increase, since the inductance continues to decrease, as shown in Fig. 4-

28. This is not the case for the commercial benchmark inductor, see Fig. 4-28. Consequently, the inductor with conductor width, w , of 5 mm becomes inferior to the benchmark due to these circuit considerations above this current, presenting a limiting case for our study. It should also be noted in this context that the losses in the conductors have little influence on the overall system efficiency, see the discussion of Fig. 3-34. In terms of system efficiency, these losses are found to be negligible, see section 4.6.3. On the other hand, the inductor with wider conductor width has lower conduction loss compared with the inductor with narrow conductor width. Therefore, it is difficult to decouple these two effects by using this analysis alone.

Although narrow LTCC inductors show higher efficiency at light load, it is often at the detriment of full load efficiency, as a result of having higher ohmic resistance. At a full load current of 12.5 A, it is observed that the efficiency drops by around 2 %, compared with using the 23 nH commercial air-gapped inductor (two 47 nH commercial inductors connected in parallel). This translates to an additional 275 mW resistive loss at a full load current of 12.5 A, in the inductor due to higher ohmic resistance. However, this loss is still small compared to the losses in the active devices. One way to solve this problem is a reduction of the resistivity of the conductor material.

In summary, it is found that by reducing the conductor width of the inductor increases the change in inductance with load current. For this inductor structure without a discrete air gap, as DC current increases, the core adjacent to the conductor starts to saturate. This causes the average magnetic path length to increase. This increase in the average magnetic path length becomes more pronounced when the conductor width of the inductor decreases, which helps to bring about the non-linear behavior of the inductor.

This brings about further improvement in light load efficiency as discussed in section 4.2.3. However, it could be at the detriment of the electrical transient load response of the converter at light load. Hence, in the design of the inductor, the tradeoff between light load efficiency and transient response has to be taken into account.

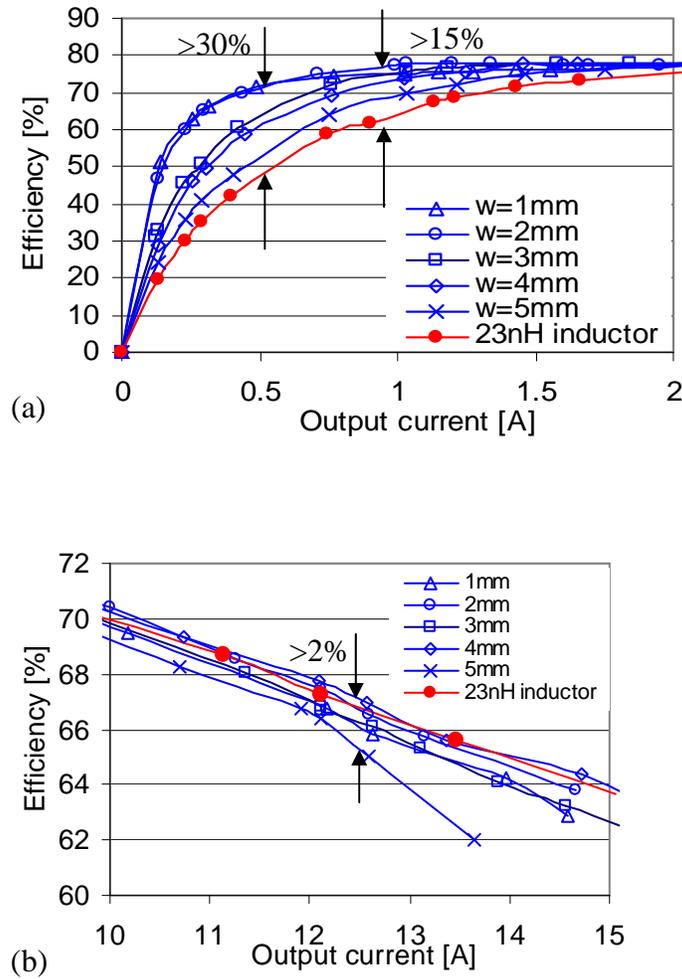


Figure 4-30 Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for inductors with conductor widths between 1 mm to 5 mm.

4.6.2 Effect of Varying Core Thickness

In this set of experiments, the core thickness of the conductor is varied to study its effect on light load efficiency of the converter. The core thickness, g , as shown in Fig. 4-7, is varied between $173\ \mu\text{m}$ to $520\ \mu\text{m}$, with other geometry parameters like conductor width, w , and conductor thickness, e , kept constant at $2\ \text{mm}$ and $0.4\ \text{mm}$, for the set of experiments. Two other sets of experiments were conducted with conductor widths of $3\ \text{mm}$ and $4\ \text{mm}$, while conductor thickness is kept constant at $0.4\ \text{mm}$. The fabrication procedure as described in association with Fig. 2-20 is again not affected, with the exception that a different number of layers of tapes were used for the bottom and top main layers to vary the core thickness, g .

Figure 4-31 shows the change of inductance with output current for conductor width, (a) $w = 2\ \text{mm}$, (b) $w = 3\ \text{mm}$, and (c) $w = 4\ \text{mm}$, conductor thickness, $e = 0.4\ \text{mm}$ and core thickness, g , varying between $173\ \mu\text{m}$ to $520\ \mu\text{m}$, which corresponds to 4 to 12 layers of ferrite tape to form the top and bottom main layers. This conforms to expectations, since reducing the volume of the core material will reduce the inductance. Figure 4-32 show the (a) light load and (b) heavy load efficiency of the converter when the above set of inductors is used in the Buck converter for $w = 2\ \text{mm}$. Figure 4-33 and Fig. 4-34 show that for $w = 3\ \text{mm}$ and $w = 4\ \text{mm}$ respectively.

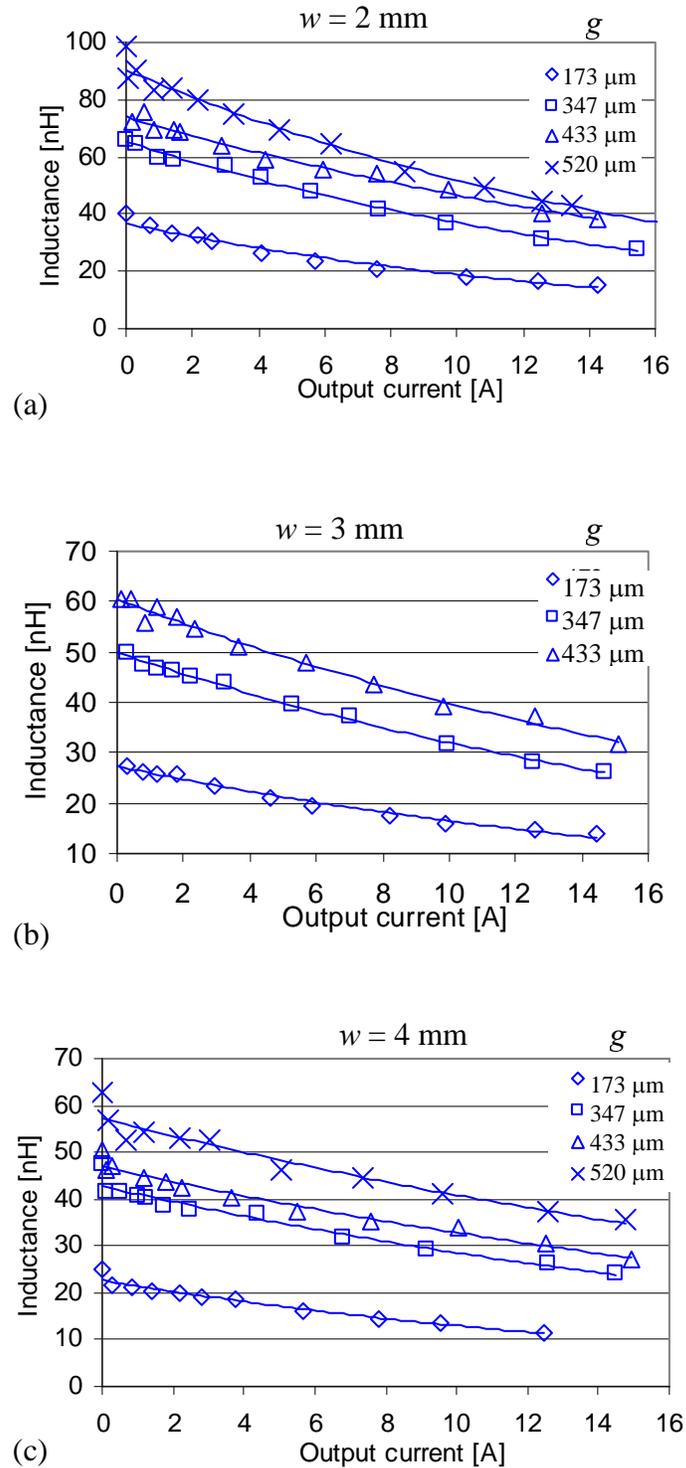


Figure 4-31 Change of inductance with output current for conductor width, (a) $w = 2 \text{ mm}$, (b) $w = 3 \text{ mm}$, (c) $w = 4 \text{ mm}$, conductor thickness, $e = 0.4 \text{ mm}$ and core thickness, g , varying between 173 μm to 520 μm .

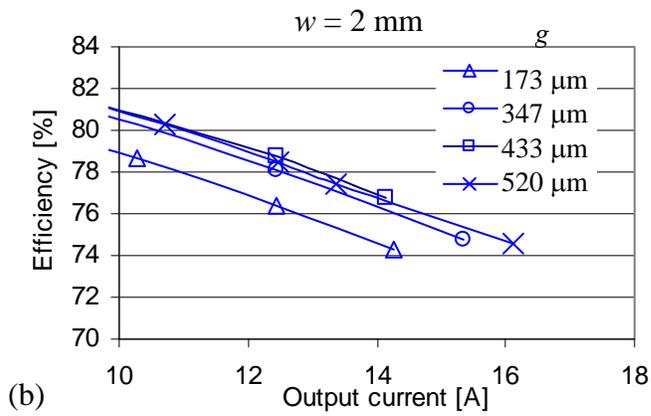
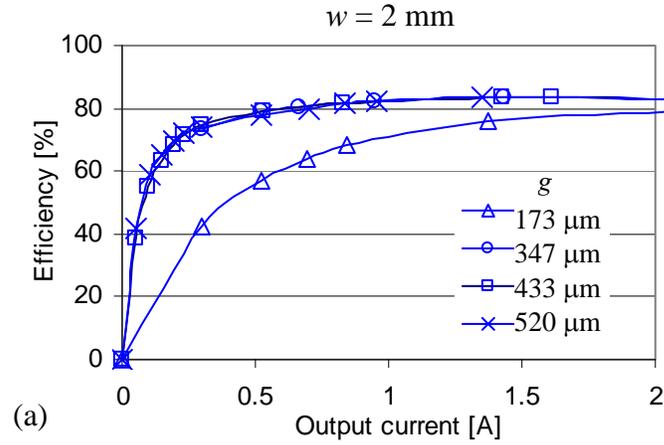
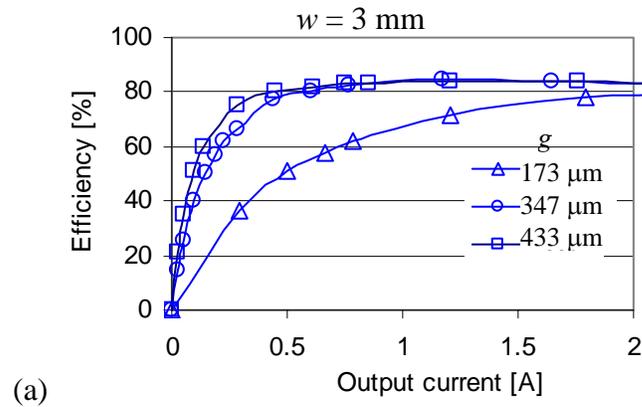


Figure 4-32 Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for core thickness variation between $173 \mu\text{m}$ to $520 \mu\text{m}$ for $w = 2 \text{ mm}$.



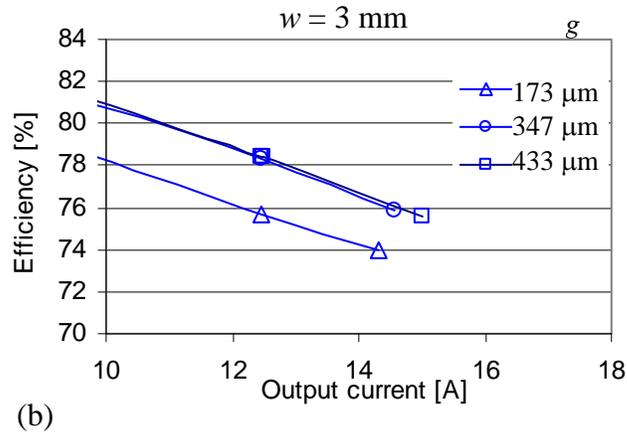


Figure 4-33 Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for core thickness variation between 173 μm to 520 μm for $w = 3$ mm.

From the efficiency curves, it is apparent that the inductor with thinner core has significantly lower overall efficiency, which is attributed to its significantly lower inductance. As a result, the ripple current is large, leading to larger losses in the switches. For inductors with core thickness varying from 347 μm to 520 μm , the efficiency curves are similar, though the inductor current ripple difference is close to 40 %. This implies that there is a critical core thickness (inductance value), beyond which, there is no significant improvement in power stage efficiency. This is because, beyond the critical core thickness, as core thickness increases, inductance increases, which leads to a decrease in switching losses in the MOSFETs due to a smaller current ripple. However, core losses in the inductor increases due to increased core volume, which negates the effect of the decrease in switching losses. The other two sets of inductors with core thickness varying between 173 μm to 520 μm , keeping conductor widths constant at 3 mm and 4 mm respectively, show similar results.

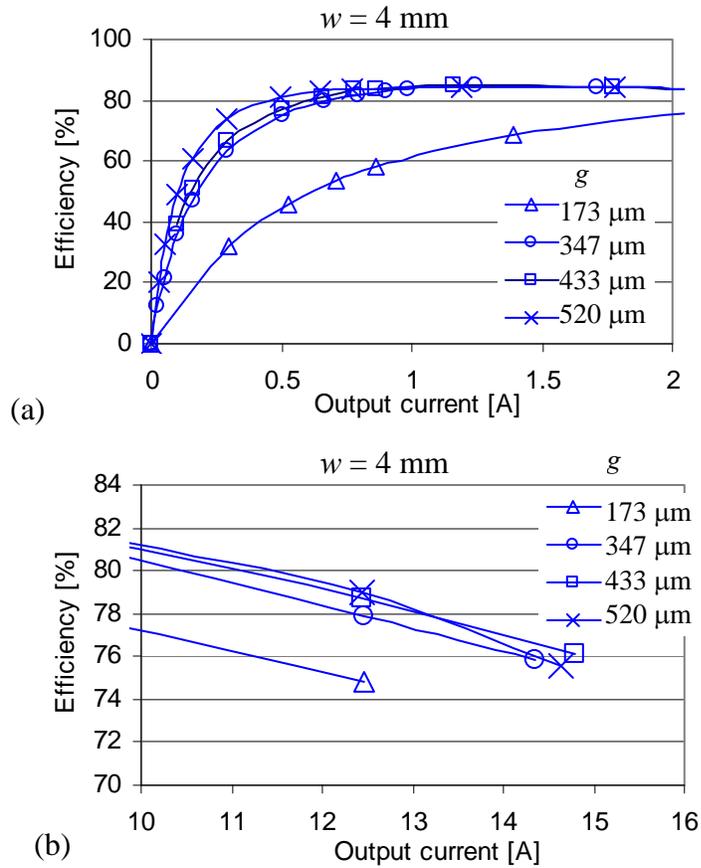


Figure 4-34 Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load for core thickness variation between 173 μm to 520 μm for $w = 4$ mm.

In summary, sufficient core thickness is necessary to increase the inductance of the inductor. Low inductance value is detrimental from the power loss point of view. There seems to be a critical inductance value, whereby increasing the inductance further, does not result in significant improvement in power stage efficiency especially at low power. This is circuit related and will not be discussed further in this dissertation.

4.6.3 Effect of Varying Conductor Thickness

Increased conductor thickness is necessary to decrease the DC resistance of the inductor. In this set of experiments, the conductor thickness is varied to observe its effect

on inductance and light load efficiency of the power stage. Figure 4-35 shows the change in inductance with output current for inductors with conductor thickness in the range of 260 μm to 550 μm . The conductor width and core thickness of the inductors are kept constant at 3 mm and 0.4 mm respectively. The fabrication procedure is similar to that described in Fig. 2-20. In fabricating inductors with varying conductor thickness, the number of ferrite tapes is varied between 4 to 12 sheets for the middle main layer. Figure 4-36 shows the power stage efficiency vs. I_{out} . It is observed that increasing conductor thickness from 260 μm to 550 μm does not result in significant improvement in the overall efficiency of the converter, leading to the conclusion that the resistive losses in the inductors are small in comparison to other losses in the system for this case. In addition, since the internal core geometry also changes, it indicates that the possible change in core losses due to the changes in magnetic flux distribution also has negligible effect in this case.

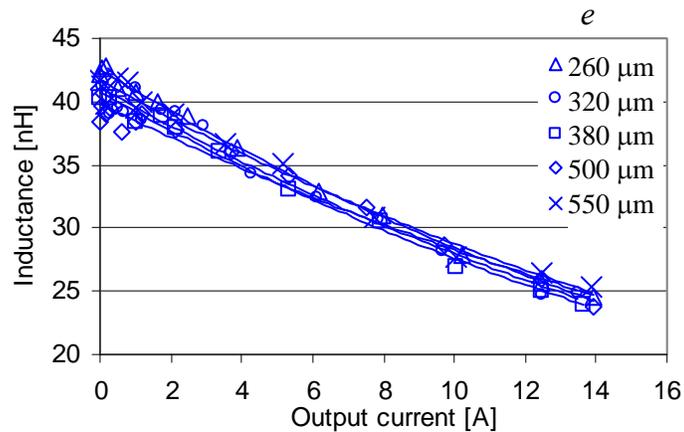


Figure 4-35 Change of inductance with output current for conductor width, $w = 3$ mm, core thickness, $g = 0.4$ mm and conductor thickness, e , varying between 260 μm to 550 μm .

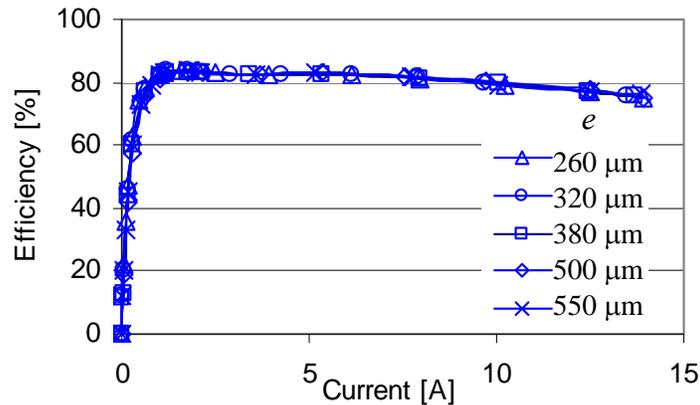


Figure 4-36 Power stage efficiency vs. output current using inductors with conductor width, $w = 3$ mm, core thickness, $g = 0.4$ mm and conductor thickness, e , varying between $260 \mu\text{m}$ to $550 \mu\text{m}$.

4.6.4 Effect of Varying Number of Parallel Conductors

It is known that multiple conductors in parallel, with each conductor surrounded by an electrically insulated magnetic material, helps to alleviate current crowding at the two sides of a rectangular conductor. This is due to partial magnetic isolation of the conductors, which reduces proximity effect between the conductors. Besides, it is also of interest to find out whether there will be an appreciable difference in the inductance change with load current, and the effect of multi-conductor inductor on converter performance, particularly the light load efficiency. In this section, the inductors are investigated with different numbers of parallel conductors, ranging from 1 to 3. They are designed to have similar inductance values at full load. The effect of having different numbers of parallel conductors is studied, particularly the impact on converter efficiency at both light load and heavy load. The footprint of the inductors is kept constant, and the same as the single conductor inductor in order to have a fair packaging comparison.

In the design of the multi-conductor inductor, the conductor width is used to vary the inductance value. In order to obtain a similar inductance value for the inductors with different number of parallel conductors, the width of each conductor for an inductor with 3-parallel conductors will be narrower than that of an inductor with 2-parallel conductors. It is also noted here that in order to obtain a similar inductance at full load, the total conductor cross-sectional area may not be the same. Since an appropriate quantitative model does not yet exist, we estimated the desired conductor widths by trial and error.

Figure 4-37 shows the change in inductance with output current for LTCC inductors with number of parallel conductors, $n = 1$ to $n = 3$, in comparison with the commercial discrete air-gap surface mount 23nH inductor. The LTCC inductors are designed to have a full load inductance value similar to that of the commercial inductor. However, it is noted here that at a full load current of 12.5A, the inductance of the LTCC inductors are lower than expected. This is due to inaccuracy in the dimensional control during the inductor fabrication process and can be improved in future. The lower inductance value at full load will result in lower full load converter efficiency.

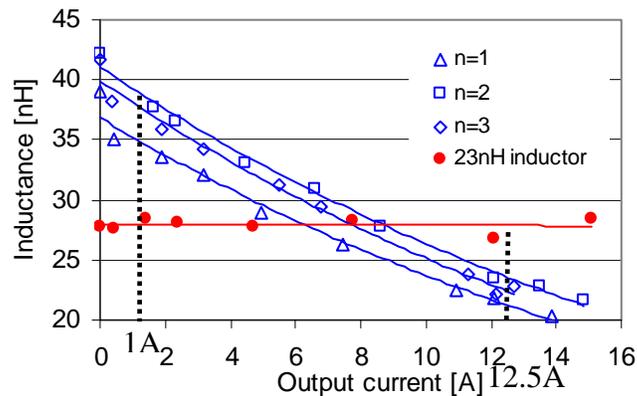


Figure 4-37 Change of inductance with output current.

Figure 4-38(a) shows the power stage efficiency at light load and Fig. 4-38(b) shows the efficiency at heavy load. The light load efficiency does not vary much with the number of parallel conductors. Besides, the improvement in light load efficiency is also evident, as illustrated by the greater than 10% improvement in efficiency at a light load current of 1 A. That this value is lower than the previously found improvement with the single conductor inductors is attributable to the lower inductance at light load for the multi-conductor case, as indicated when comparing Fig. 4-37 to Fig. 4-28. At heavy load, there is also no obvious change in efficiency with the number of parallel conductors. However, it is observed that the heavy load converter efficiency is lower for the LTCC inductors. This is due to the increased switching losses, attributable to the unexpected lower inductance of the LTCC inductors at full load, which has been explained previously.

In summary, varying the number of parallel conductors (between 1 and 3) within the same footprint does not result in an appreciable difference in the inductance change with load current. Hence, there is also no observable change in light load or heavy load efficiency when LTCC inductors with different number of parallel conductors are used, under the constraint of a footprint equal to 8 mm x 20 mm.

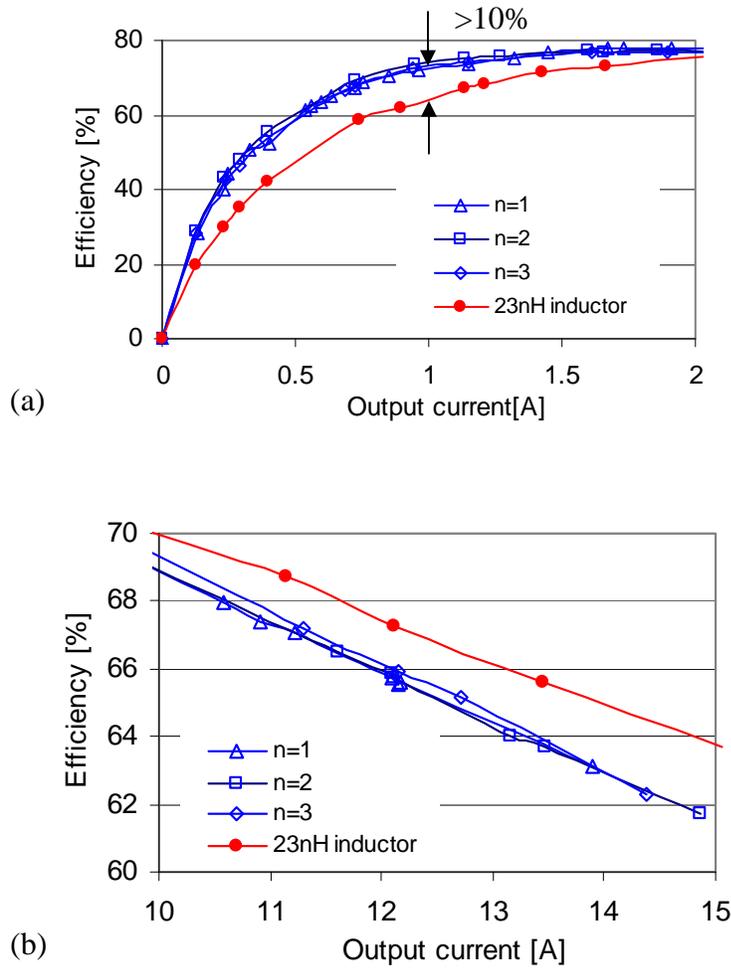


Figure 4-38 Power stage efficiency vs. output current comparison at (a) light load and (b) heavy load, for multi-conductor inductor.

4.7 Inductance Model for LTCC Inductor

An empirical model has been developed for an inductor structure with a rectangular conductor embedded in the magnetic material (see Fig. 4-7). The model relates inductance with the geometry factors of the inductor as well as its magnetic permeability, given by equation (4-5) [47].

$$\frac{L}{l} = \frac{\mu}{2\pi} \ln\left(\frac{\frac{w+e}{2} + 2g + \sqrt{\frac{w^2+e^2}{2} + 4g^2} + 2g(w+e)}{\frac{w+e}{2} + \sqrt{\frac{w^2+e^2}{2}}}\right) \quad (4-5)$$

where

μ : magnetic permeability

w : conductor width

e : conductor thickness

g : core thickness

l : conductor length, and

L : inductance.

To account for the non-linear behavior of this inductor structure under the influence of DC current, the equation is modified empirically. Figure 4-39 shows the plot of $\log(\mu_r)$ vs. I_{DC} for inductors of conductor widths varying from 1 mm to 5 mm. It is observed that the curves of $\log(\mu_r)$ vs. I_{DC} can be described by the following relationship:

$$\log(\mu_r) = a + b \cdot I_{DC} \quad (4-6)$$

where a and b are empirical constants obtained from curve fitting. Figure 4-40 shows the graphs of coefficient ' a ' and coefficient ' b ' vs. conductor width. Hence, a and b can be expressed as a function of conductor width, w .

$$\log(\mu_r) = a(w) + b(w) \cdot I_{DC} \quad (4-7)$$

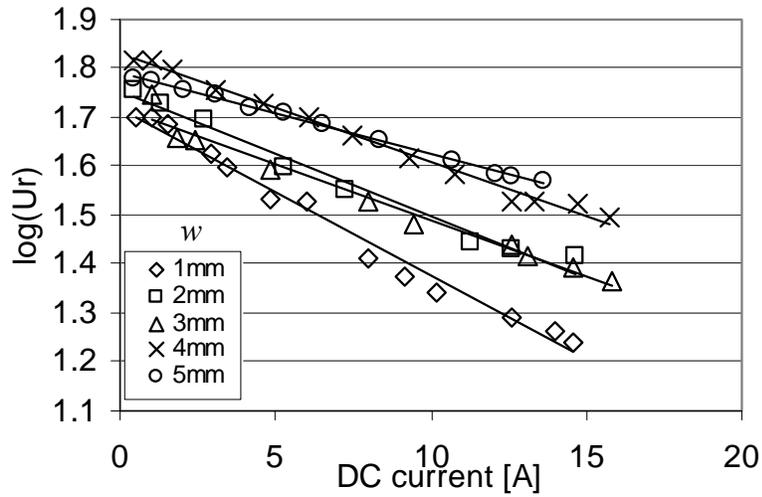


Figure 4-39 Graph of $\log(\mu_r)$ vs. I_{DC} for inductors of conductor widths varying from 1 mm to 5 mm.

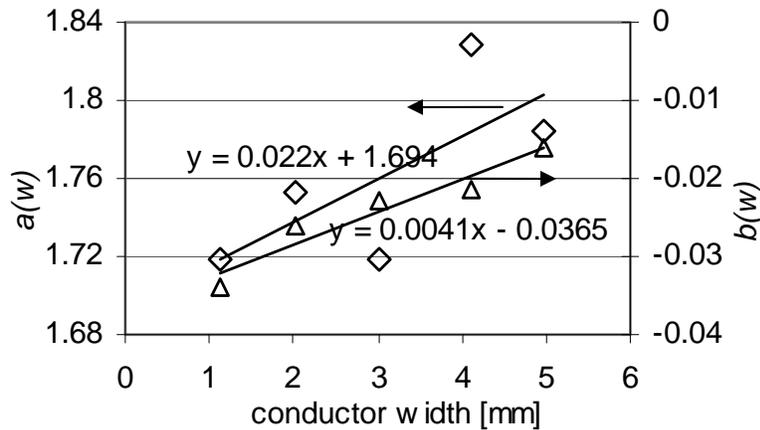
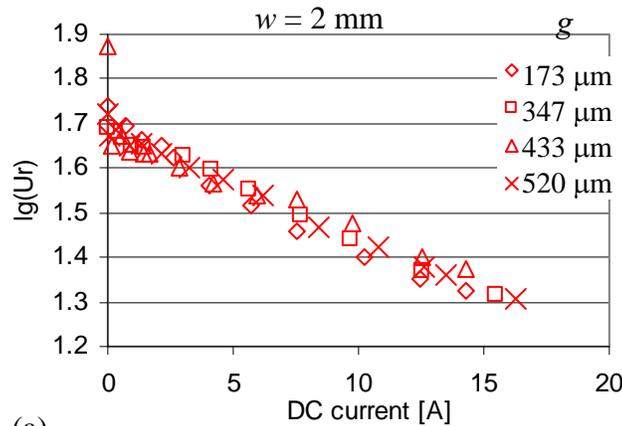


Figure 4-40 Graph of coefficient ' $a(w)$ ' and ' $b(w)$ ' of equation (4-7) vs. conductor width.

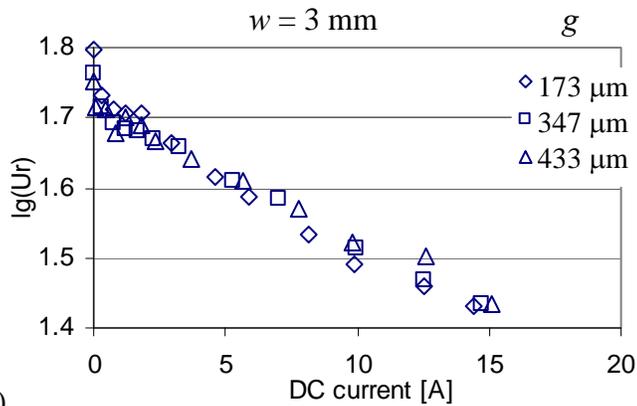
Core thickness g , as shown in Fig. 4-7, is varied, and the graph of $\log(\mu_r)$ vs. I_{DC} is plotted in Fig. 4-41 (a), (b), and (c) for conductor widths of 2 mm, 3 mm, and 4 mm. It is observed that the change in $\log(\mu_r)$ with I_{DC} is independent of the change in core thickness. Since the conductors are of the same dimensions for the samples with various core thicknesses, the average magnetic path length would be similar, which will result in

a similar magnetic flux density distribution in the core. The increase in core thickness will increase the inductance, but it has little impact on the effective permeability.

Conductor thickness e , shown in Fig. 4-7, is varied, and the graph of $\log(\mu_r)$ vs. I_{DC} is plotted in Fig. 4-42. It is observed that the change in $\log(\mu_r)$ with I_{DC} is independent of the change in conductor thickness. Since the conductor width is much larger than the conductor thickness, as long as the increase in conductor thickness is much smaller than the conductor width, the average magnetic path length would be similar for all the samples. This results in a similar magnetic flux density distribution in the core for all the samples, resulting in a similar effective permeability.



(a)



(b)

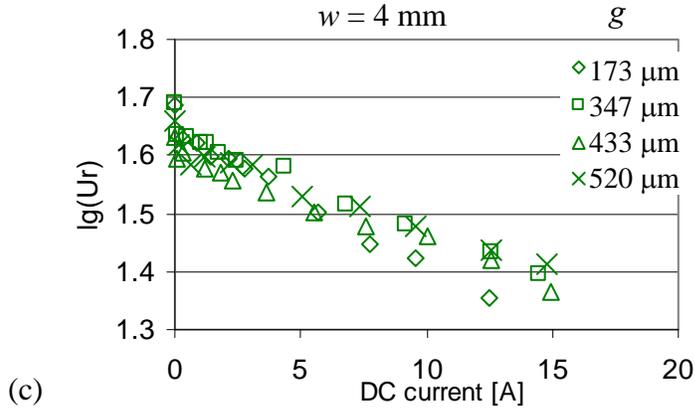


Figure 4-41 Graph of $\log(\mu_r)$ vs. I_{DC} for inductors of various core thickness, g , for conductor widths of (a) 2 mm and (b) 3 mm and (c) 4 mm.

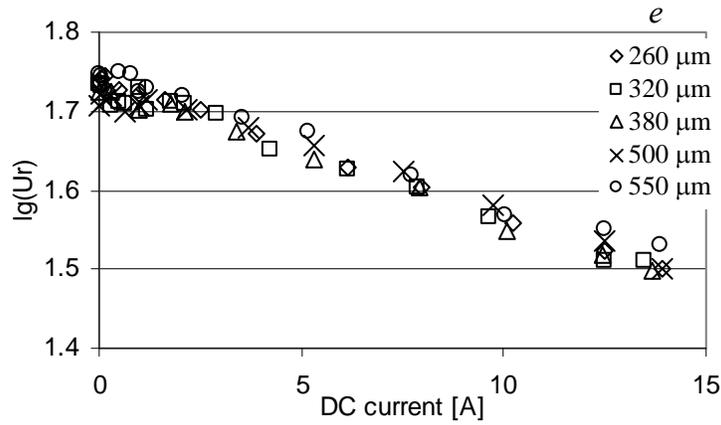


Figure 4-42 Graph of $\log(\mu_r)$ vs. I_{DC} for inductors of various conductor thickness, e .

Based on the results obtained above, an empirical model for the LTCC inductor is developed as shown in equation (4-8).

$$\frac{L}{l} = \frac{U_r \mu_0}{2\pi} \ln\left(\frac{\frac{w+e}{2} + 2g + \sqrt{\frac{w^2 + e^2}{2} + 4g^2 + 2g(w+e)}}{\frac{w+e}{2} + \sqrt{\frac{w^2 + e^2}{2}}}\right) \quad (4-8)$$

where $U_r = 10^{4w(I_{DC}+5.4)+0.037(46.4-I_{DC})}$.

This empirical model is developed based on LTCC inductors fabricated using the low-permeability ($\mu_r = 60$ from datasheet) LTCC magnetic tape purchased from Electroscience Labs [28]. This model is valid for LTCC planar inductors fabricated using the low-permeability tape with conductor widths between 1 mm to 4 mm, conductor thickness 180 μm to 550 μm , and core thickness 170 μm to 520 μm , measured at a switching frequency of 4 MHz DC current from 0 A to 16 A. Since the above model is developed based on the low-permeability LTCC ferrite tape purchased from Electroscience Labs, it is not applicable for other ferrites. For inductors made using other ferrites, the same methodology can be used to obtain the empirical model.

4.8 Inductor Design Procedure

In section 4.7, an empirical model for LTCC inductors fabricated using the low permeability tape purchased from Electroscience Labs [28] has been developed. In this section, the inductor design procedure will be described and will be illustrated with a design example, followed by actual fabrication and experimental verification. Fig. 4-43 shows the design flow diagram.

1. Obtain inputs

Table 4-2 shows the specifications of an example in designing an inductor using the above empirical model. The conductivity of the Ag/Pt paste is estimated to be 1.7×10^7 S/m, as discussed in Chapter 3. Figure 4-44 shows the position where the inductor electrodes must lie and the given footprint of the inductor.

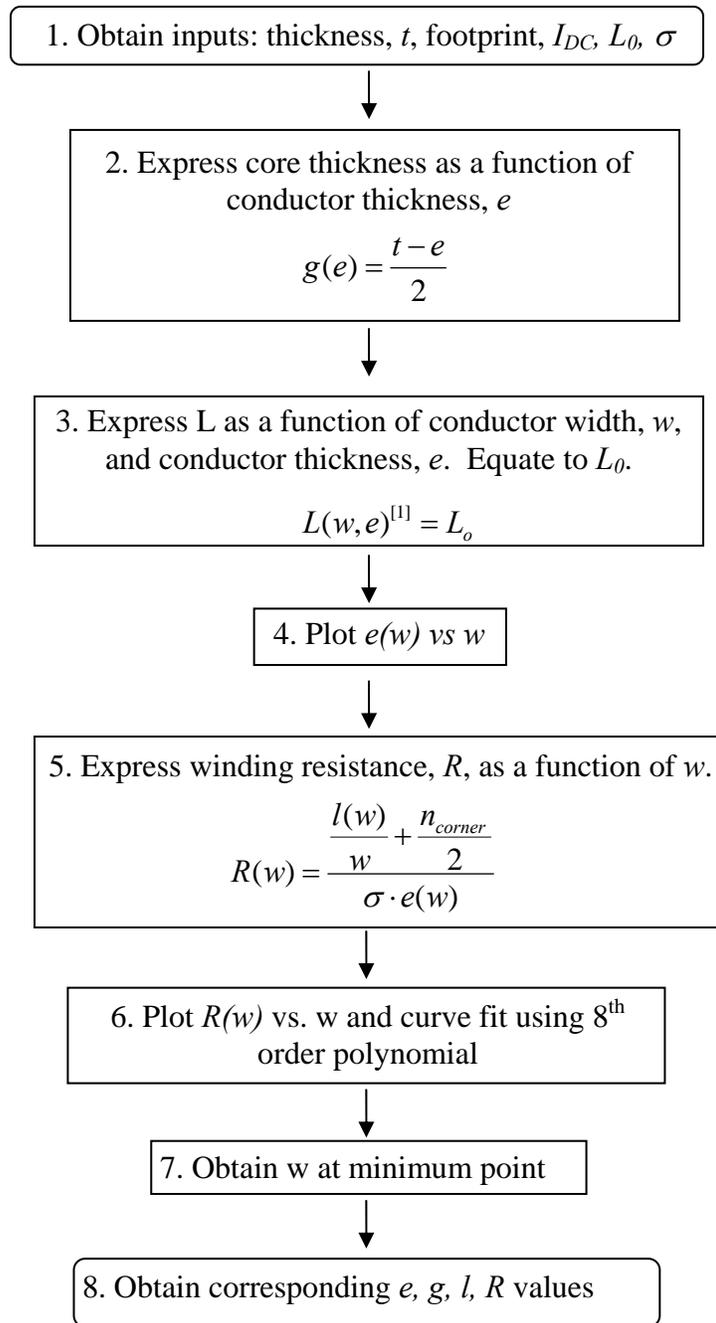


Figure 4-43. Flow diagram for LTCC inductor design.

2. Express core thickness as a function of conductor thickness, e

Since the magnetic core surrounds the conductor, as in Fig. 4-7, core thickness, t , can be expressed as a function of conductor thickness, e ,

$$g(e) = \frac{t - e}{2} \quad (4-9)$$

Table 4-2 Specifications for inductor

L_0 [nH]	25
I_{DC} [A]	12.5
Distance between electrodes [mm]	10
Thickness [mm]	1

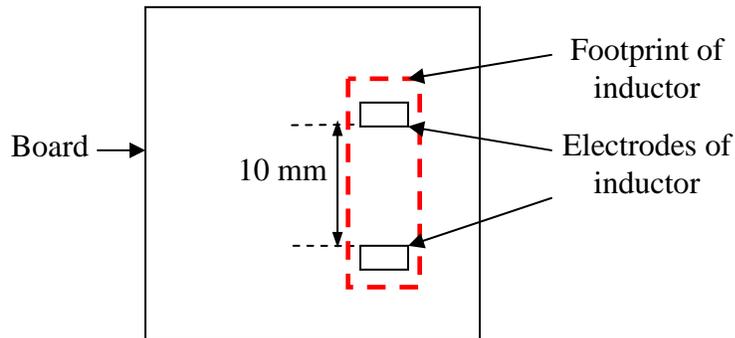


Figure 4-44 Footprint of the inductor and the position of the electrodes.

3. Express L as a function of conductor width, w , and conductor thickness, e . Equate to L_0 .

U_r in equation (4-8) is expressed as a function of conductor width, w

$$U_r = 10^{4w(I_{DC} + 5.4) + 0.037(46.4 - I_{DC})}$$

$$U_r(w) = 10^{85.6w + 1.12} \quad (4-10)$$

Equation (4-8) is then expressed as a function of w and e , and equated to L_0 .

$$L(w, e) = l \cdot \frac{U_r(w) \cdot \mu_0}{2\pi} \ln \left(\frac{\frac{w+e}{2} + 2g(e) + \sqrt{\frac{w^2+e^2}{2} + 4g(e)^2 + 2g(e)(w+e)}}{\frac{w+e}{2} + \sqrt{\frac{w^2+e^2}{2}}} \right) \quad (4-11)$$

$$L(w, e) = 25nH \quad (4-12)$$

4. Plot conductor thickness, e , as a function of conductor width, w .

From (4-11), the only two unknowns are w and e . Hence, conductor thickness, e , can be plotted as a function of conductor width, w , as shown in Fig. 4-45.

5. Express winding resistance, R , as a function of w .

The resistance of the conductor can be expressed as:

$$R(w) = \frac{l(w)}{\sigma \cdot e(w) \cdot w} \quad (4-13)$$

6. Plot $R(w)$ vs. w and curve fit using 8th order polynomial

Resistance, R , is plotted as a function of conductor width, w , using (4-13) as shown in Fig. 4-46. From Fig. 4-45, $e(w)$ shows a monotonically decreasing relationship with w . From (4-13), the product of $e(w)$ and w gives a parabolic relationship of $-Aw^2 + Bw$. The reciprocal of this relationship gives $R(w)$, which will result in the relationship shown in Fig. 4-46.

7. Obtain w at minimum point

From Fig. 4-46, the minimum point is found to be at $w = 1.17$ mm.

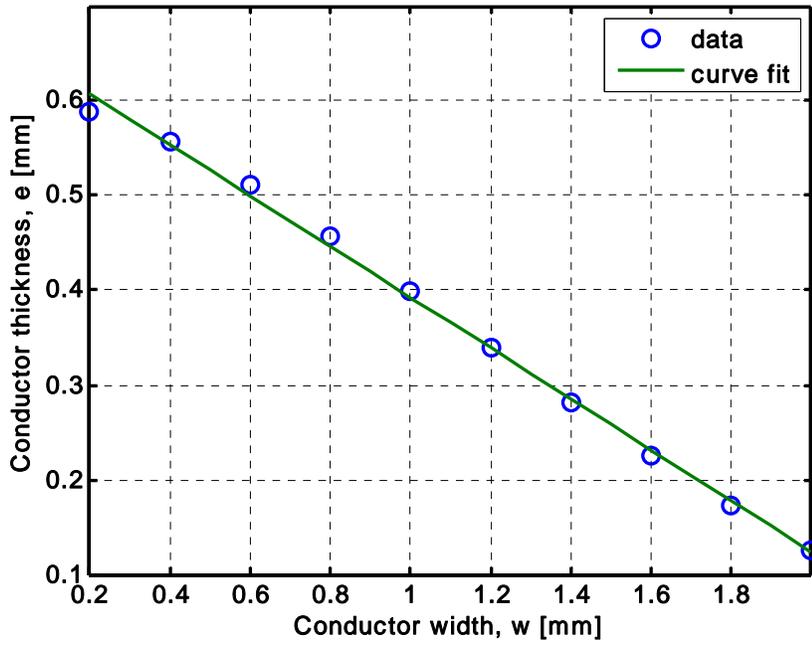


Figure 4-45 Graph of conductor thickness, e , vs. conductor width, w , for $L = 25$ nH.

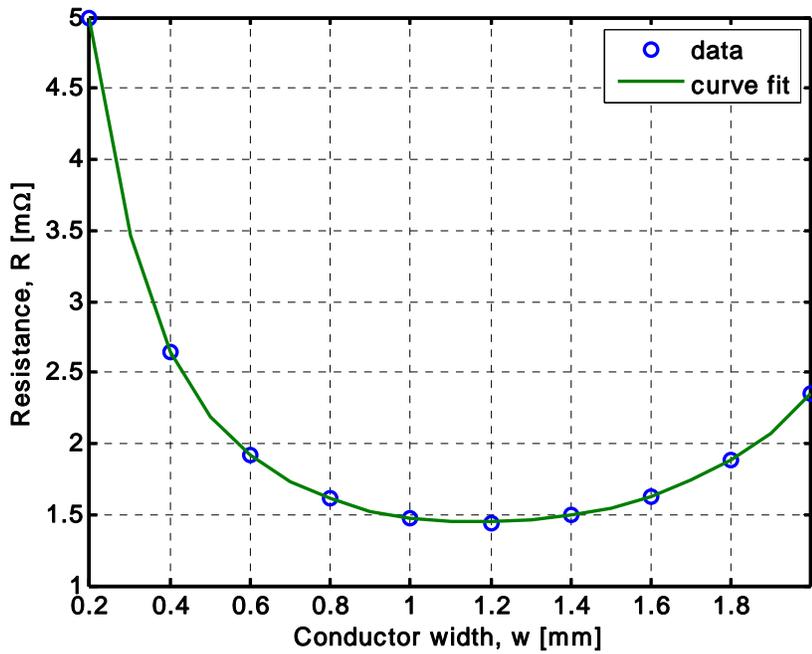


Figure 4-46 Graph of resistance, R , vs. conductor width, w .

8. Obtain corresponding e , g , l , R values

Winding resistance, $R(w)$, can be obtained from (4-13). Conductor thickness $e(w)$ can be obtained from (4-11) and (4-12). Core thickness, $g(e)$, can be obtained from (4-9). Table 4-3 tabulates the design values of e , g , l , w and R for $L_0 = 25$ nH.

Table 4-3 Inductor Design Values

L [nH]	e [mm]	g [mm]	l [mm]	w [mm]	R [Ω]
25	0.348	0.326	10.0	1.17	1.44

4.9 Summary

It is shown that LTCC technology is a very promising technology for the integration of power electronics applications. Based on the inductor geometries discussed in section 4.2, the short winding inductor with magnetic core enclosing the conductor, gives the flexibility in varying the conductor's cross-sectional area, which makes it suitable for achieving low DC resistance and high current capability.

Conductors with elongated almond cross-sectional shape, which are characteristic of screen printed conductors, are undesirable for high frequency applications from the conduction loss point of view. The overall power loss becomes greater when the conductor is surrounded by magnetic material, as verified by simulation, as well as experimentally. Hence, it is desirable to alter the conventional method of screen printing conductor paste on LTCC green tape to obtain a rectangular conductor cross-sectional shape for applications in which power loss is to be minimized. In addition, from the

point of view of footprint occupied by the conductor, conductors with rectangular conductor cross-section offer the potential to obtain a much smaller footprint compared to conductors with almond cross-sectional shapes.

In the parametric variation of inductor geometry, it is found that by reducing the conductor width of the inductor increases the change in inductance with load current. For this inductor structure without a discrete air gap, as DC current increases, the core adjacent to the conductor starts to saturate, which causes the average magnetic path length to increase. This increase in the average magnetic path length becomes more pronounced when the conductor width of the inductor decreases, which results in the non-linear behavior of the inductor. This brings about further improvement in light load efficiency as discussed in section 4.2.3.

An empirical model is subsequently developed based on LTCC inductors fabricated using the low-permeability ($\mu_r = 60$ from datasheet) LTCC magnetic tape purchased from Electrosience Labs [28]. This model is valid for LTCC planar inductors fabricated using the low-permeability tape with conductor widths between 1 mm to 4 mm, conductor thickness 260 μm to 550 μm , and core thickness 173 μm to 520 μm , measured at a switching frequency of 4 MHz DC current from 0 A to 16 A. Since the above model is developed based on the low-permeability LTCC ferrite tape purchased from Electrosience Labs, it is not applicable for other ferrites. For inductors made using other ferrites, the same methodology can be used to obtain the empirical model. An inductor design flow diagram has been formulated to help in the design of such inductors. An inductor design example is shown to demonstrate the use of the design flow diagram.

Chapter 5. LTCC Inductor as Substrate

5.1 Overview

The popularity of portable devices makes size reduction necessary to decrease the dimensions of the overall system. In a dc-dc converter, the bulkiest components are the capacitors and the inductors. In the previous chapter, the manufacturing and design of low profile (1 mm) chip inductors have been investigated as a first step in size reduction of these DC-DC converters. Configuring the inductor as the substrate carrying the semiconductor and the other electronic components is a next step as a means to mitigate the negative impact of inductor size on power density and is investigated in this chapter. As the conductive traces are placed in the proximity of the magnetic substrate, however, the parasitic trace inductances increase, adversely affecting circuit operation. A solution to this problem by introducing a conductive shield between the inductor as substrate and the active circuitry is also addressed in this chapter.

It is investigated that the presence of a metal shield reduces trace inductances and improves circuit performance and shows that there is a minimum shield thickness required to minimize losses associated with ringing. The role of shield conductivity is to lower the trace inductance and minimize power loss, as well as the positioning of the shield to minimize inductance, is investigated.

5.2 Circuit Specifications

The test circuit used is a 5 V – to – 1.1 V, 16 A buck converter as already discussed in Chapter 4, but now operating at 1.3 MHz. The full load inductance is designed to be 64 nH. Fig. 4-1 shows the circuit schematic.

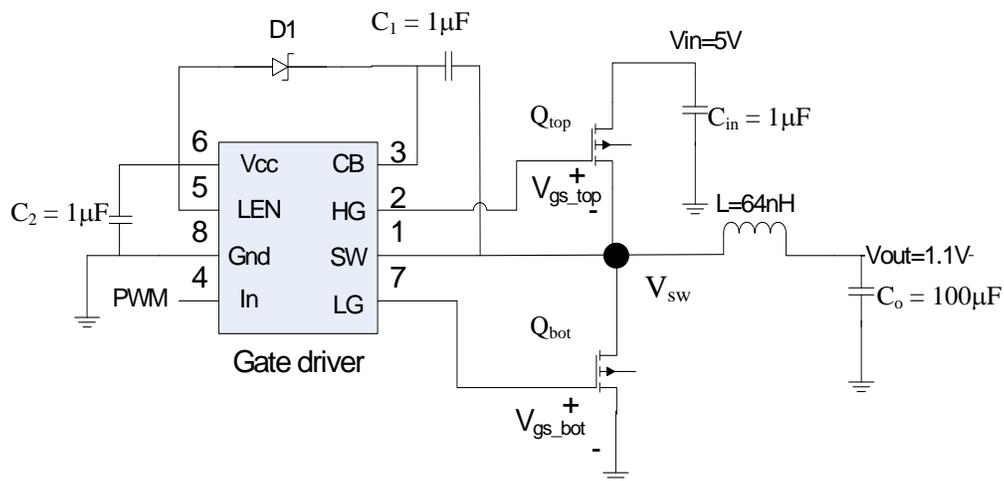


Figure 5-1 Buck converter circuit diagram.

The top MOSFET (Q_{top}) used is HAT2168 [120] and the bottom MOSFET (Q_{bot}) is HAT2165 [121]. The pulse width modulation (PWM) input is provided from a signal generator. The input voltage of the gate drive is 5V.

5.3 Geometry of Integrated Inductor

The integrated inductor is of low profile with a thickness less than 2 mm. The winding is embedded in the magnetic substrate. Fig. 5-2 (a) shows the 3-D drawing of the planar inductor. Fig. 5-2 (b) shows the cross-sectional drawing of the inductor.

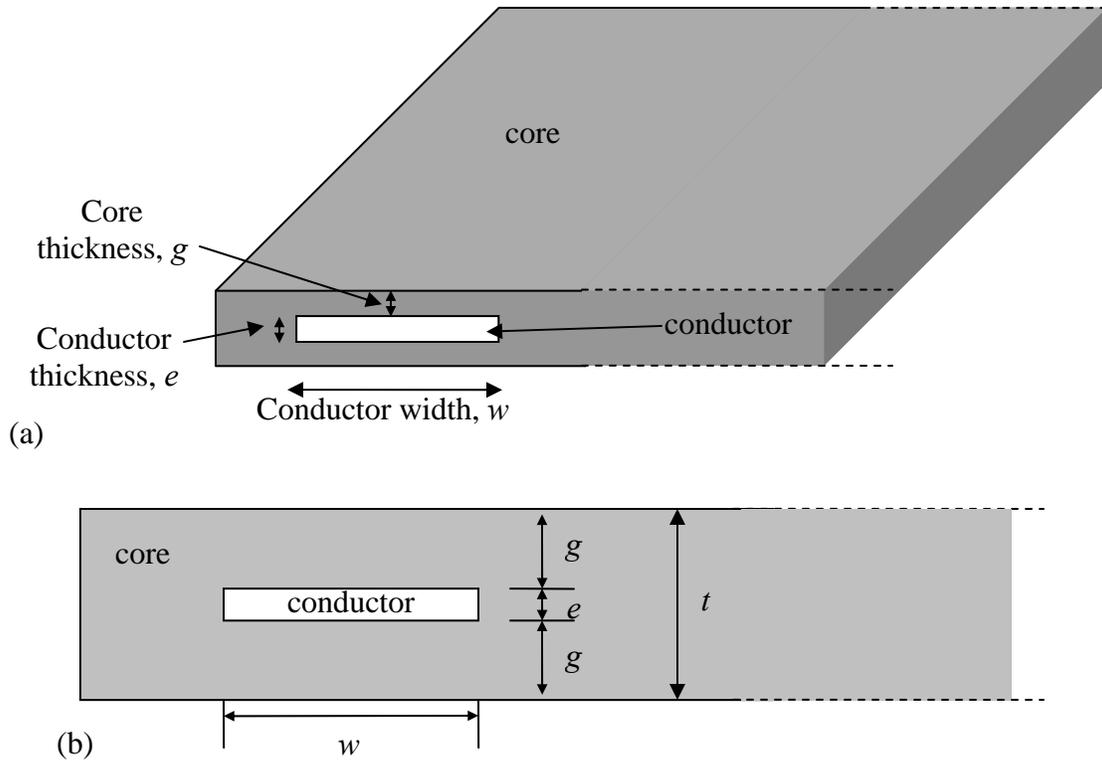


Figure 5-2 LTCC inductor substrate. (a) Three-dimensional view of LTCC planar inductor, (b) cross-sectional diagram of LTCC planar inductor.

5.4 Substrate Inductor Design Procedure

In section 4.7, an empirical model for LTCC inductors fabricated using the low permeability tape purchased from Electrosience Labs [28] was developed. In this section, the inductor design procedure will be described and will be illustrated with a design example, followed by actual fabrication and experimental verification of its properties. Fig. 5-3 shows the design flow diagram.

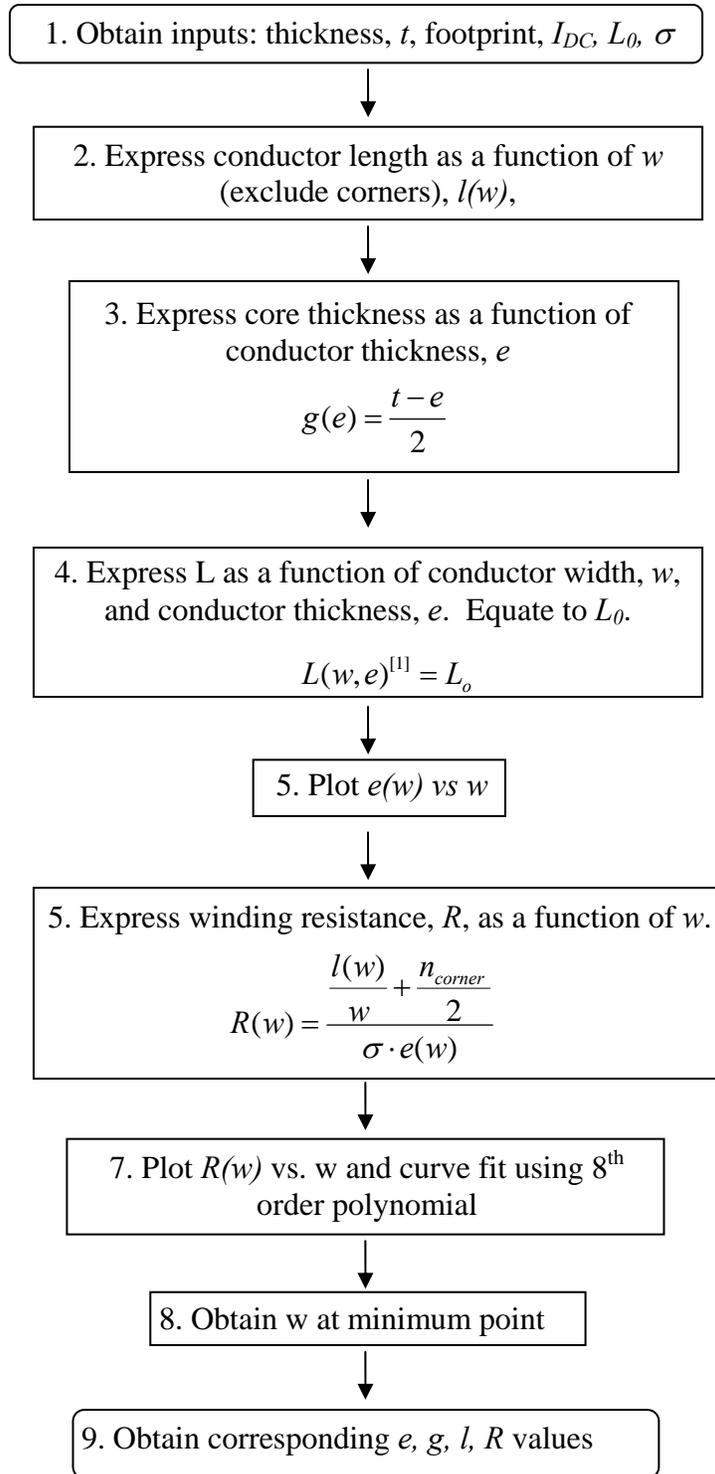


Figure 5-3. Flow diagram for LTCC inductor substrate design.

1. Obtain inputs

Table 5-1 shows the specifications of an example in designing an inductor using the above empirical model. The conductivity of the Ag/Pt paste is estimated to be 1.7×10^7 S/m, as discussed in Chapter 3. Figure 5-4 shows the given footprint of the inductor and the position of the electrodes. A through hole is specified in the middle of the structure where the windings of the inductor must avoid.

Table 5-1 Specifications for inductor

L_0 [nH]	100
I_{DC} [A]	16
Dimensions [mm ³]	28 x 28 x 1.4

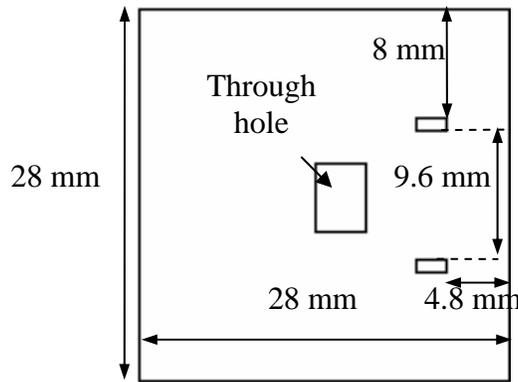


Figure 5-4 Footprint of the inductor and the position of the electrodes. Windings must avoid the through hole in the structure.

2. Express conductor length as a function of w (exclude corners), $l(w)$

An allowance of 2 mm is left between the edges of the conductor to the edges of the structure. Hence, the allowable footprint for the conductor is reduced to 24 x 24 mm.

Fig. 5-5 shows the winding for the design example. Neglecting the contribution of inductance by the corners of the winding, the length of the winding is expressed as a function of conductor width, w .

$$l(w) = 2 \times (6 - w + 21.2 - 2w) + 24 - 2w$$

$$l(w) = 78.4 - 8w \tag{5-1}$$

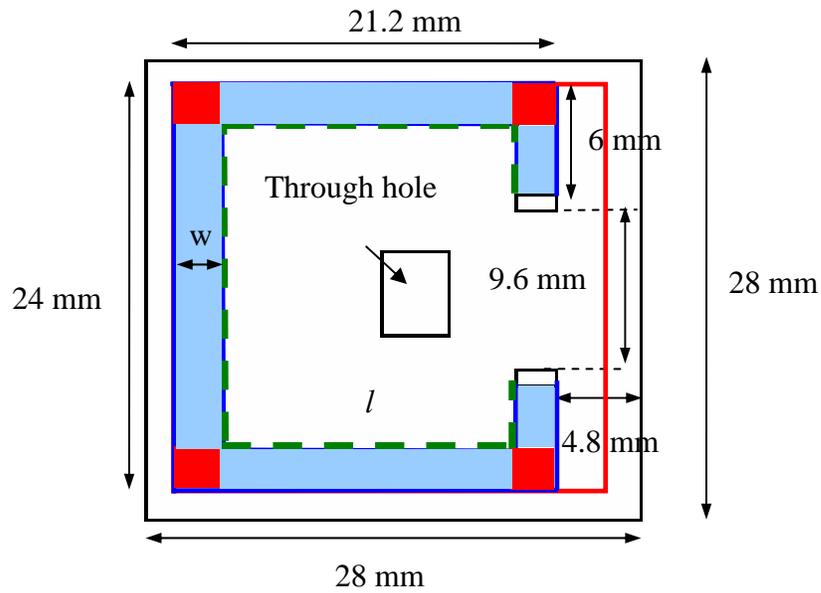


Figure 5-5 Design of winding for LTCC inductor example.

3. Express core thickness as a function of conductor thickness, e

Since the magnetic core surrounds the conductor, as in Fig. 5-2, core thickness can be expressed as a function of conductor thickness,

$$g(e) = \frac{t - e}{2} \tag{5-2}$$

4. Express L as a function of conductor width, w , and conductor thickness, e . Equate to L_0 .

Ur in equation (4-8) is expressed as a function of conductor width, w

$$U_r = 10^{4w(I_{DC}+5.4)+0.037(46.4-I_{DC})}$$

$$U_r(w) = 10^{85.6w+1.12} \quad (5-3)$$

Equation (4-7) is then expressed as a function of w and e , and equated to L_0 .

$$L(w, e) = l(w) \frac{U_r(w) \cdot \mu_0}{2\pi} \ln \left(\frac{\frac{w+e}{2} + 2g(e) + \sqrt{\frac{w^2+e^2}{2} + 4g(e)^2 + 2g(e)(w+e)}}{\frac{w+e}{2} + \sqrt{\frac{w^2+e^2}{2}}} \right) \quad (5-4)$$

$$L(w, e) = 100nH \quad (5-5)$$

5. Plot conductor thickness, e , as a function of conductor width, w .

From (5-4), the only two unknowns are w and e . Hence, conductor thickness, e , can be plotted as a function of conductor width, w , as shown in Fig. 5-6. Fig. 5-6 shows a monotonically decreasing relationship between w and e .

6. Express winding resistance, R , as a function of w .

The resistance for the straight portion can be expressed as:

$$R_1(w) = \frac{l(w)}{\sigma \cdot e(w) \cdot w} \quad (5-6)$$

The resistance for a corner can be expressed as:

$$R_{corner} = 0.56R_{square} \quad (5-7)$$

where R_{square} is the resistance of the conductor in the form of a square.

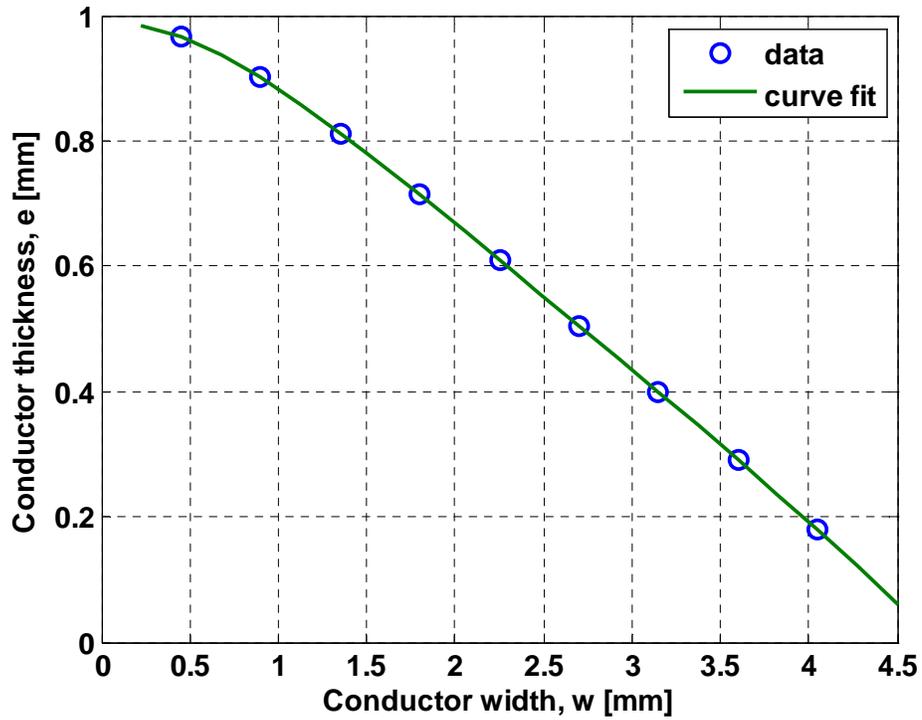


Figure 5-6 Graph of conductor thickness, e , vs. conductor width, w , for $L = 100$ nH.

R_{square} can be expressed as:

$$R_{square} = \frac{1}{\sigma \cdot e(w)} \quad (5-8)$$

For simplicity, we let

$$R_{corner} = 0.5R_{square} \quad (5-9)$$

The resistance for the n corners can be expressed as:

$$R_2(w) = \frac{n_{corner}}{2 \cdot \sigma \cdot e(w)} \quad (5-10)$$

where n_{corner} is the number of corners in the winding.

The resistance of the winding can be expressed as the sum of (4-13) and (4-17)

$$R(w) = \frac{\frac{l(w)}{w} + \frac{n_{corner}}{2}}{\sigma \cdot e(w)} \quad (5-11)$$

7. Plot $R(w)$ vs. w and curve fit using 8th order polynomial

Resistance R is plotted as a function of conductor width, w , as shown in Fig. 5-7, using (5-11). Equation (5-11) will result in a curve of the shape shown in Fig. 5-7, due to a similar reason given in Chapter 4.8.

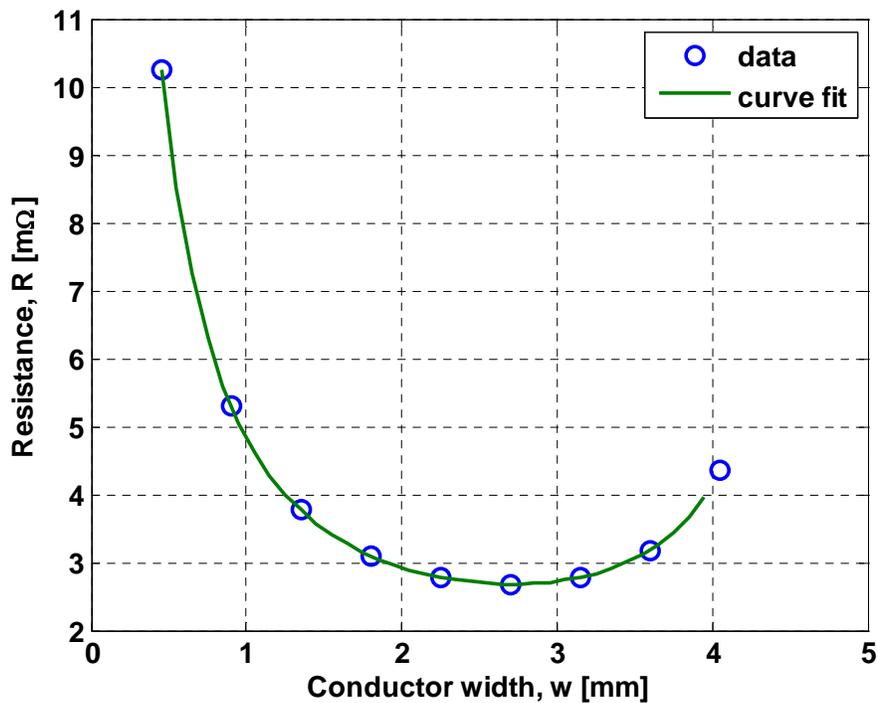


Figure 5-7 Graph of resistance, R , vs. conductor width, w .

8. Obtain w at minimum point

The minimum point is found to be at $w = 2.72$ mm.

9. Obtain corresponding e , g , l , R values

Conductor length, $l(w)$, can be obtained from (5-1). Winding resistance, $R(w)$, can be obtained from (5-11). Conductor thickness $e(w)$ can be obtained from (5-4) and (5-5). Core thickness, $g(e)$, can be obtained from (5-2). Table 5-2 tabulates the design values of e , g , l , w and R for $L_0 = 100$ nH.

Table 5-2 Inductor Design Values.

L [nH]	e [mm]	g [mm]	l [mm]	w [mm]	R [ohm]
100	0.501	0.449	56.7	2.72	2.68

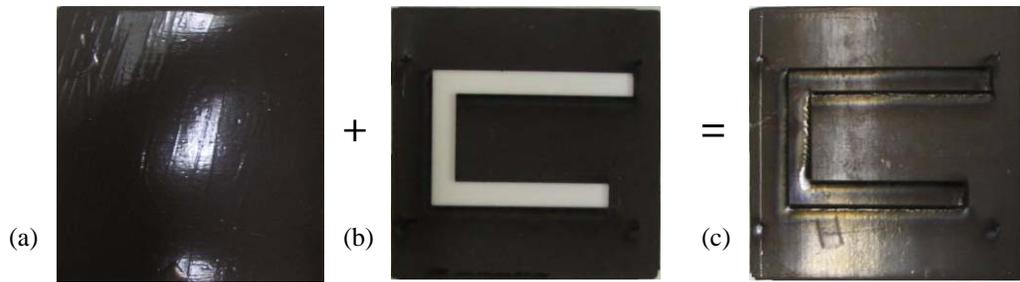
5.5 Effect of LTCC Inductor as Substrate

Using the inductor as the substrate helps in reducing the footprint of the circuitry, since the surface real estate which was occupied by the bulky component is freed for other devices and components. However, having a magnetic material below the circuitry increases parasitic inductances in circuit traces and adversely affects circuit performance. In this section, an LTCC inductor is fabricated and used as a substrate where its surface is populated by the other devices and components of the circuit.

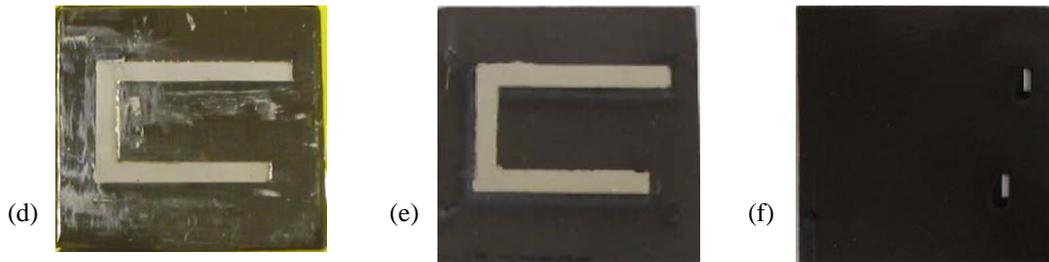
5.5.1 Inductor Substrate Fabrication Procedure

The inductor is designed to operate at a switching frequency 1.3 MHz, carrying a nominal DC current of 16 A in a 5 V - to - 1.1 V buck converter. For this configuration,

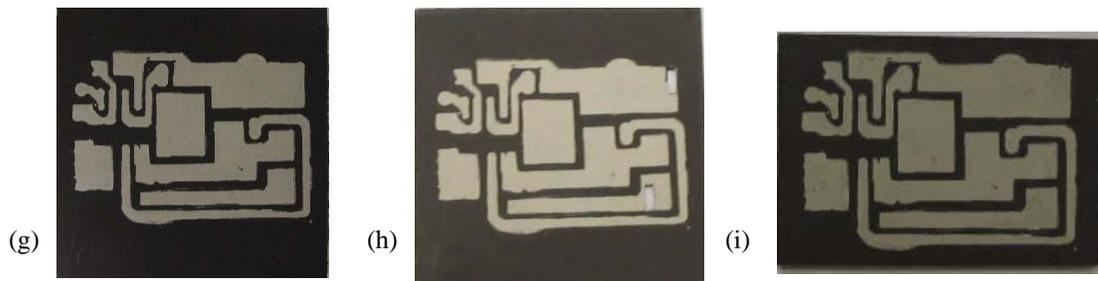
the inductor is designed to have a value of 64 nH at full load. The inductor is designed using the empirical model developed in Chapter 4.7. In this section, the fabrication procedure of the inductor substrate is described. Fig. 5-8 shows the inductor substrate fabrication procedure.



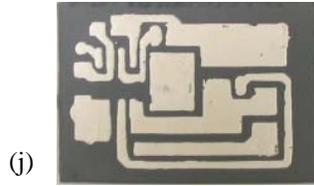
(a) Main bottom layer comprising 7 layers of ferrite tape, (b) main middle layer comprising 8 layers of ferrite tape, with C-shaped slot cut using laser, (c) laminate (a) with (b).



(d) Conductor paste dispensed into slot using a squeegee, with Kapton tape covering the rest of the surface. Sample is heated to 70 °C to dry conductor paste. Procedure is repeated 3 to 4 times until conductor paste fills slot completely. (e) After Kapton tape is removed. (f) top main layer comprising 7 layers of ferrite tape.



(g) Stencil printed circuit layout on ferrite tape, (h) laminate (f) with (g) and cutting through holes for inductor electrodes, (i) laminate (e) with (h), filling up holes with Ag/Pt paste and laser cutting sample into desired size.



(j) Sample after sintering.

Figure 5-8 Inductor substrate fabrication procedure.

In Fig. 5-8(a), 7 layers of ferrite tape of dimensions 3.5 cm x 3.5 cm are laminated to form the bottom main layer and the top main layer. The middle main layer comprises 8 layers of laminated ferrite tape. The inductor winding slot is subsequently cut using laser in the middle main layer, as shown in Fig. 5-8(b). The bottom main layer and middle main layer are stacked together and laminated at a temperature of 70 °C and a pressure of 10 MPa (1500 psi) (see Fig. 5-8(c)). The kapton tape is adhered to the surface of the sample, exposing the slot. The Ag/Pt paste is then dispensed into the slot using a squeegee (see Fig. 5-8(d)). Sample is heated to 70 °C to dry the conductor paste. The procedure of dispensing conductor paste and drying are repeated 3 to 4 times until conductor paste fills the slot completely. The kapton tape is then removed (see Fig. 5-8(e)). Two small slots for the electrodes are cut using laser into the top main layer, as shown in Fig. 5-8(f).

Circuit layout pattern is stencil printed on a single layer of ferrite tape, as shown in Fig. 5-8(g). The top main layer and the single layer of ferrite tape with stencil printed circuit layout are laminated. Small slots are cut in the layer with circuit layout pattern (see Fig. 5-8(h)). The sample with Ag/Pt paste-filled-slot (Fig. 5-8(e)) and the top main layer with circuit layout pattern (Fig. 5-8(h)) are then laminated. The holes in the small slots for electrodes are filled with Ag/Pt paste. The sample is then cut into the desired

size using laser (see Fig. 5-8(i)). The sample is then sintered using the sintering profile shown in Fig. 2-21. Fig. 5-8(j) shows the sample after sintering.

5.5.2 Large Signal Measurement Results

The fabricated inductor is used as a substrate where other devices and components for a buck converter are soldered on its surface. The circuit is operated as a 5 V – to – 1.1 V buck converter at 2 MHz. Fig. 5-1 shows the circuit diagram of a Buck converter. Fig. 5-9 shows the photograph of the inductor substrate with surface mount devices to form a single-phase buck converter. Table 5-3 tabulates the parts used in the fabrication of the prototype.

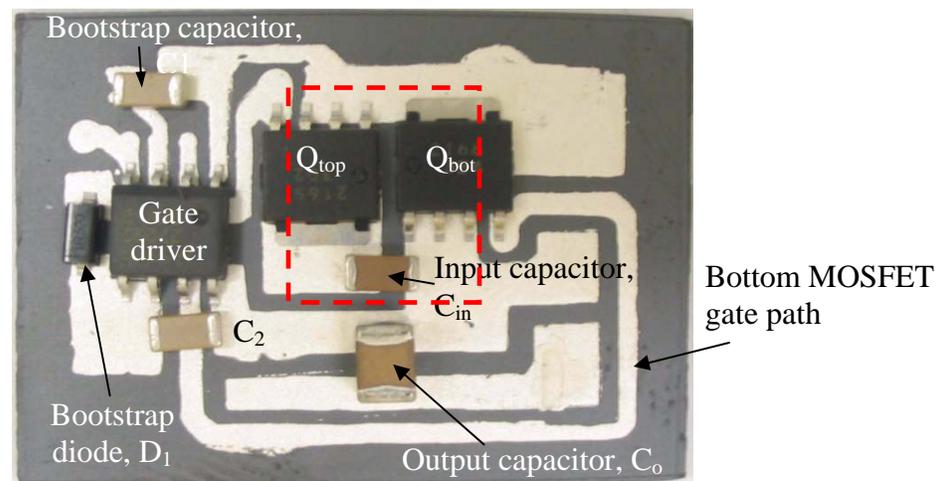


Figure 5-9 Buck converter on inductor substrate.

Figure 5-10 shows that the gate voltage of the top and bottom MOSFETs of the buck converter contains clear oscillations due to the presence of parasitic inductance. Due to the presence of the magnetic substrate directly beneath the circuitry, parasitic inductances of the traces become magnified. In Fig. 5-10 (a), it is evident that due to the trace

inductance of the bottom MOSFET's gate path, as indicated on Fig. 5-9, there is a large amplitude oscillation when the MOSFET switches turn on and off. In Fig. 5-10 (a), it can be seen that the large amplitude oscillation might have caused the bottom MOSFET to exhibit false turn on.

Table 5-3 Parts Used In Fabrication of Prototype.

Part	Part Number	Attributes
Q_{top}	HAT2168 [120]	$R_{ds,on}=8.8m\Omega, V_{DSS}=30V, Q_{gd}=2.4nC, SO8$
Q_{bot}	HAT2165 [121]	$R_{ds,on}=3.3m\Omega, V_{DSS}=30V, Q_{gd}=7.1nC, SO8$
Gate driver	LM27222 [122]	$t_{pd}=8ns, t_{dead_time}=10ns, V_{in}=4 \text{ to } 6.85V$
C_1, C_2, C_{in}	1206	10 μF , 25 V
C_o	1210	100 μF , 6.3 V
D_1	MBR130T1 [123]	30 V, 1 A, SOD123, Schottky diode

To verify this, the bottom MOSFET gate path on the inductor substrate is opened and the gate driver and bottom MOSFET gate is directly connected via a copper strip. Figure 5-10 (b) shows the V_{GS} of the MOSFETs after the modification. It is evident that the presence of an inductive substrate results in greater loop inductance and hence a poorly damped voltage oscillation at the switching node that can lead to operation when it is supposed to be turned off. This can lead to degradation in the overall efficiency of the converter.

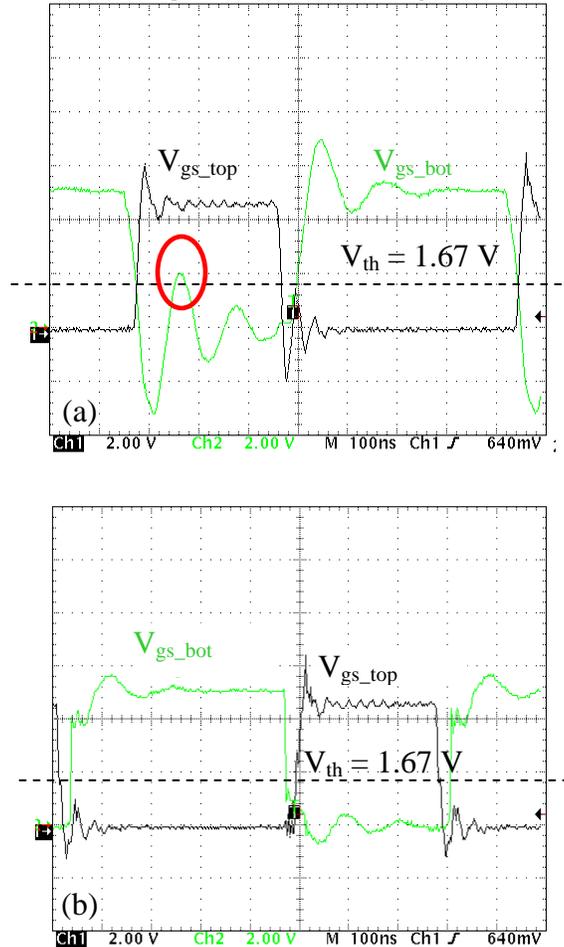


Figure 5-10 V_{GS} of the top and bottom MOSFETs (a) before (b) after connecting gate driver directly to the gate of the bottom MOSFET via copper strip.

5.6 Review of Electromagnetic Shielding Techniques

In monolithic radio frequency integrated circuit (RFIC) design, coupling noise from inductors is reduced by using conductive guard rings surrounding the inductors [124, 125]. These guard rings serve as a shield to reduce the magnetic flux cross-talk coupling from the inductor with other inductors and from affecting other circuitry. In high speed digital signals, a meshed ground plane reduces degradation in signal rise time and voltage

amplitude due to lower line capacitances. However, the longer current path in the case of a meshed ground plane reduces propagation velocity due to increased line inductance [126]. A floating shield technique is implemented to reduce passives loss on silicon substrate for inductors in RFICs. In this case, the floating conductive shields link the equal but opposing electric field from the passive component and its current return path, keeping the floating shield at 0 V without an explicit ground reference [127]. In the following section, we introduce the use of a shield between the magnetic component and the rest of the circuit to mitigate the impact of the magnetic substrate on circuit loop inductance.

5.7 LTCC Inductor Substrate with Conductive Shield

In the previous section, an inductor was fabricated using LTCC technology and used as a substrate for the active circuitry by printing conductive traces on the inductor magnetics and mounted devices on top. The performance of the system-on-inductor-substrate was evaluated. The presence of a magnetic substrate below the circuitry created additional parasitic inductances, which resulted in low-frequency oscillations and poor overall efficiency. By introducing a conductive shield layer between the circuitry and the inductor substrate, an attempt is made to alleviate the problem.

5.7.1 Simulation Study of Shielding for Magnetic Substrate

As observed in section 5.5, the presence of a magnetic substrate directly under the circuitry traces can cause large amplitude and low frequency ringing, which can

adversely affect circuit performance. A conductive shield is introduced between the magnetic substrate and the circuitry to alleviate the impact of the magnetic substrate on circuit performance. In this section, comparison will be made between circuit operation with and without shield. The effect of varying shield distance from circuit trace, shield thickness and shield conductivity are studied.

5.7.1.1 Electromagnetic Influence of the Shield

In order to combat the negative effect of having a magnetic substrate below, the inclusion of a conductive shield below the conductor traces is investigated. Fig. 5-11 shows the simulation structure with conductive shield between the conductive trace and magnetic substrate. The trace is a copper sheet with dimensions of 11 mm x 12 mm with thickness of 70 μm . There is a 1 mm x 5 mm slot in the trace. The dimensions were chosen to be similar to that having two MOSFETs with SO8 packages placed side by side, as shown in Fig. 5-9. The region in Fig. 5-11 is represented by the dotted lines in Fig. 5-9. The magnetic substrate has dimensions of 28 mm x 28 mm x 1.2 mm. The structure shown in Fig. 5-11 lies in the middle of the magnetic substrate. The thick arrow in Fig. 5-11 indicates the direction of current flow in the trace. Figure 5-12 shows the 2-D drawing of the section indicated by the dotted line in Fig. 5-11 for the various cases of with or without shield and with or without inductor substrate. The relative permeability of the magnetic substrate is 60. The conductivity of the shield and conductor is 1.7×10^7 S/m. Simulation is performed for a current of 1 A passing through the conductor. The frequency of the current in the simulation is 1.3 MHz.

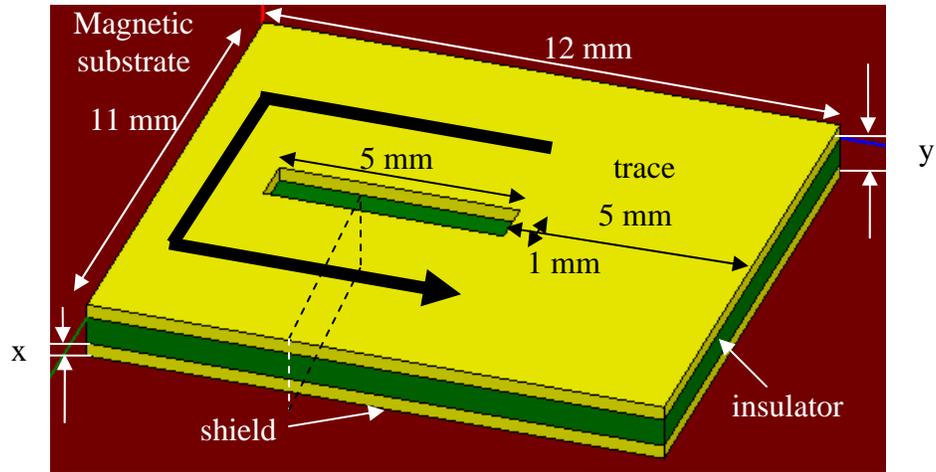
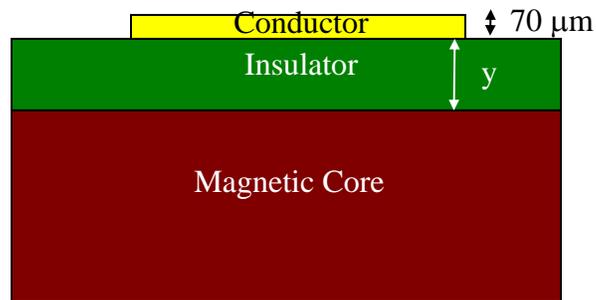


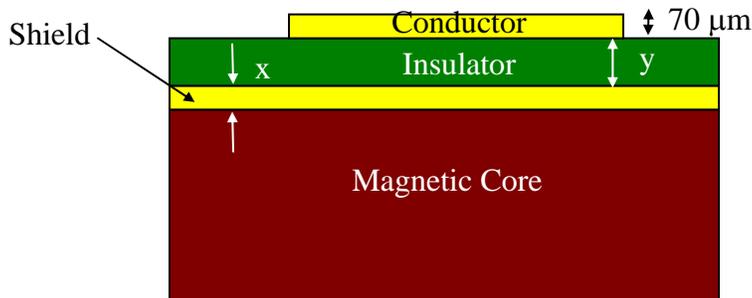
Figure 5-11 Simulation structure with conductive shield between the conductive trace and magnetic substrate.



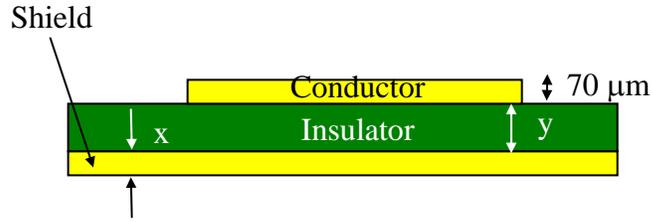
(a) Case A



(b) Case B



(c) Case C



(d) Case D

Figure 5-12 Cross-sectional drawings of simulation structures.

Figure 5-13 shows the comparison of normalized resistive loss for the four cases using case A as the base for comparison. Fig. 5-14 shows the comparison of normalized loop inductance for the four cases using case A as the base for comparison.

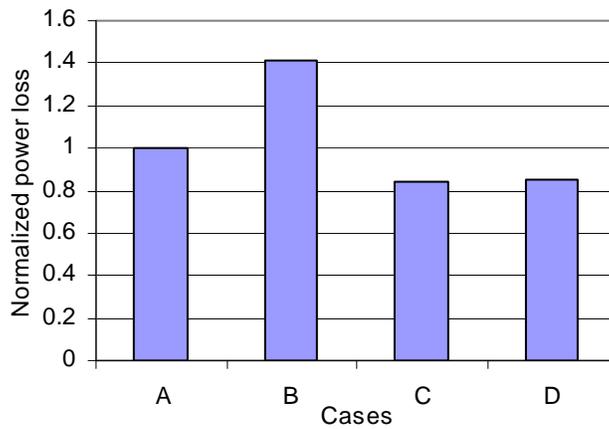


Figure 5-13 Normalized power losses for the four cases.

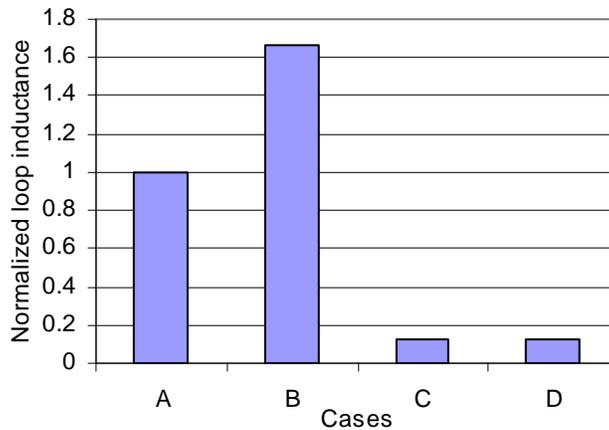


Figure 5-14 Normalized loop inductances for the four cases.

5.7.1.2 Effect of Varying Shield Distance from Conductor

The insulator thickness, y , (see Fig. 5-11) is varied between $10\mu\text{m}$ to $200\mu\text{m}$ to study its effect on loop inductance. Both the trace thickness and shield thickness are $70\mu\text{m}$. The structure similar to that in Fig. 5-11 is simulated. Fig. 5-15 shows the graph of loop inductance vs. insulator thickness. It is observed that as insulator thickness increases from $10\mu\text{m}$ to $200\mu\text{m}$, the loop inductance increases by almost 400 %. The increase in loop inductance as insulator thickness increase is because the volume between the conductor and the shield, which is available for energy storage increases. On the other hand, the resistance decreases by less than 10 %. This is because as the distance between the conductor and the shield increases, the coupling between the conductor and the shield decreases. Hence, the current induced in the shield decreases, leading to lower I^2R losses in the shield. Therefore, to reduce trace inductance, the conductor has to be placed close to the shield. From the point of view of reducing loop inductance, which is related to power loss, it is consequently recommended to minimize insulator thickness. The price for doing so is increased power loss in the shield.

5.7.1.3 Effect of Varying Shield Thickness

In this section the same structure in Fig. 5-11 is used. The shield thickness, x , is varied between $5\mu\text{m}$ to $200\mu\text{m}$ to study its effect on loop inductance and power loss of the system. The simulation is performed for a 1.3 MHz, 1 A current in the conductor. Fig. 5-16 shows the graph of power loss and loop inductance vs. shield thickness for an insulator thickness $50\mu\text{m}$ and conductive trace thickness $70\mu\text{m}$.

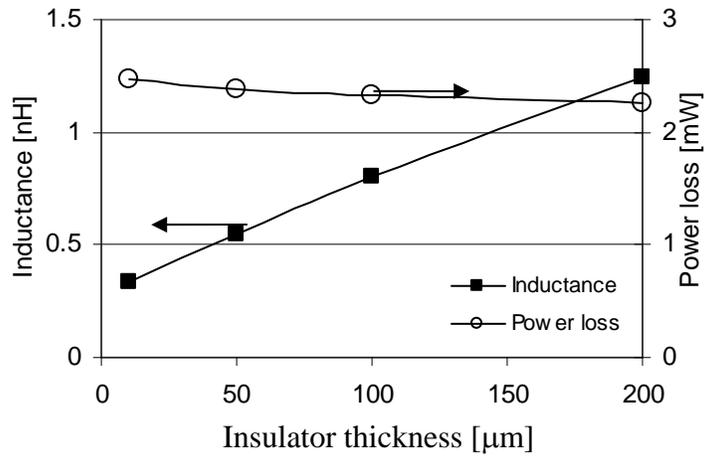


Figure 5-15 Graph of power loss and inductance vs. insulator thickness. Both the conductor thickness and shield thicknesses are 70 μm.

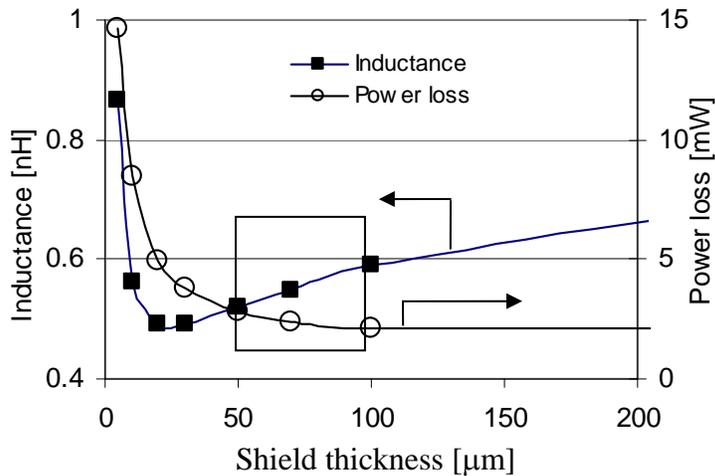


Figure 5-16 Graph of power loss and inductance vs. shield thickness. The conductor thickness is 70 μm and insulator thicknesses are 50 μm.

It is observed from Fig. 5-16 that loop inductance is very high at low shield thickness, which is attributed to the shield being ineffective at these thicknesses. The minimum loop inductance occurs at a shield thickness of between 20 to 30 μm and increases slightly as shield thickness increases. The power loss is low for thicker shield. It increases rapidly as shield thickness decreases to below 50 μm. In view of this, it is more

feasible to have a shield thickness in the range of 50 μm to 100 μm , since both inductance and power loss are low in this range. Thicker shields are not preferable since increased shield thickness implies increased cost.

5.7.1.4 Effect of Varying Shield Conductivity

In this set of simulations, the structure in Fig. 5-11 is used. The shield thickness is 70 μm and the insulator thickness is 50 μm . The current in the conductor is 1 A at 1.3 MHz. The shield conductivity is varied to observe its effect on loop inductance and power loss. Fig. 5-17 shows the plot of inductance and power loss vs. shield conductivity.

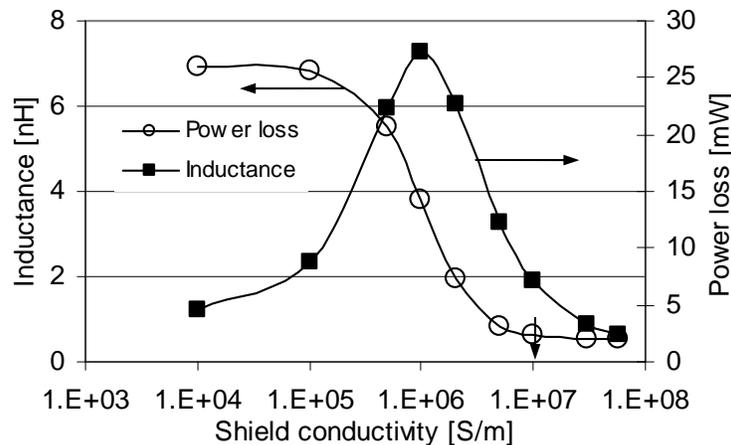


Figure 5-17 Graph of energy stored and power loss vs. shield conductivity. Conductor thickness and insulator thickness are both 50 μm . Shield thickness is 10 μm . Simulation frequency is 1.3 MHz.

When the conductivity is low, the energy stored in the system is high, which is a result of the magnetic field from the current carrying conductor penetrating the shield and entering the magnetic substrate. This manifests itself as parasitic inductance. When the conductivity is high, the shield is effective in producing an opposing current flow as a result of voltage induced in the shield, which prevents the magnetic field from entering

the magnetic substrate. Thus, shield conductivity greater than 10^7 S/m is desirable since the loop inductance and power loss are both low.

In summary, presence of magnetic substrate below a current conducting trace increases the inductance of the trace which increases power loss. By introducing a shield below the trace helps reduce the parasitic inductance of the trace as well as the overall power loss. The trace inductance can be decreased by decreasing the distance between the trace and the shield. Shield thickness in the range of 50 μm to 100 μm is recommended as a compromise between parasitic inductance and power loss. Shield conductivity greater than 10^7 S/m is desirable for the shield to be effective, for low inductance as well as for low power loss.

5.7.2 Shielded Inductor Substrate Fabrication Procedure

To investigate the effect of metal shield between circuitry and magnetic substrate, two samples were fabricated and tested. The first sample has no shield and the second sample has a grounded shield under the MOSFETs. The shield thickness printed is estimated to be around 50 μm , which is in the optimum range of thickness suggested in section 5.7.1.3. From section 5.7.1.2, it was suggested that the thinner the insulator (between the conductive trace and the shield), the lower the trace inductance. A single layer of insulating LTCC tape is used as the insulator, which has a thickness of around 80 μm . The inductor substrate with integrated shield has dimensions 24mm x 24mm x 1.3mm. Fig. 5-18 shows the inductor fabrication procedure.

In the fabrication process of the trace and shield layer, low k dielectric LTCC tape with part number ESL 41050 and Ag/Pt paste of part number 9516 are used. Both

materials are purchased from Electrosience Labs [28]. The metal trace from the gate drive to the gate of the lower MOSFET is printed on the second layer and is directly below the ground on the top layer. Fig. 5-19 shows the photograph of the trace layers (first layer) for the two samples (a) with no shield and (b) with shield. The metal shield is printed such that it is directly under the two MOSFETs. Since the MOSFETs carry large current and are hard switched, the inductance in the input loop comprising the two MOSFETs and the constant input voltage source resonates with the parasitic capacitances across the MOSFETs, resulting in voltage ringing across the MOSFETs. Hence, to reduce the parasitic inductance, a shield is introduced under the MOSFETs.

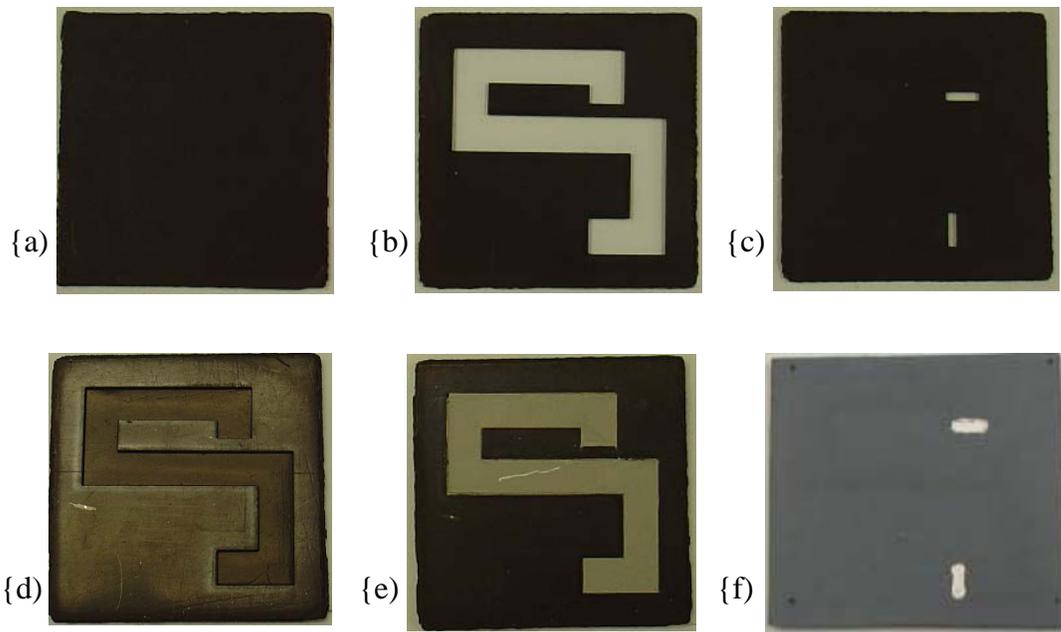


Figure 5-18 Fabrication procedure of inductor substrate. (a) Bottom main layer comprising 7 layers of ferrite tape, (b) Middle main layer comprising 8 layers of ferrite tape. An S-shape slot is cut using laser machining. (c) Top main layer comprising 7 layers of ferrite tape. Two rectangular slots for inductor's electrode cut using laser machining, (d) Laminate (a) with (b), (e) Ag/Pt paste is dispensed into the slot as described in Fig. 4-5. (f) Laminate (c) with (e), fill rectangular slots with Ag/Pt paste and sinter.

Figure 5-20 shows the improved buck converter with inclusion of metal shield above magnetic substrate. The dotted line shows the position of the shield, which is below the circuitry layer. The parts used in the fabrication of the prototypes are the same as that tabulated in Table 5-3.

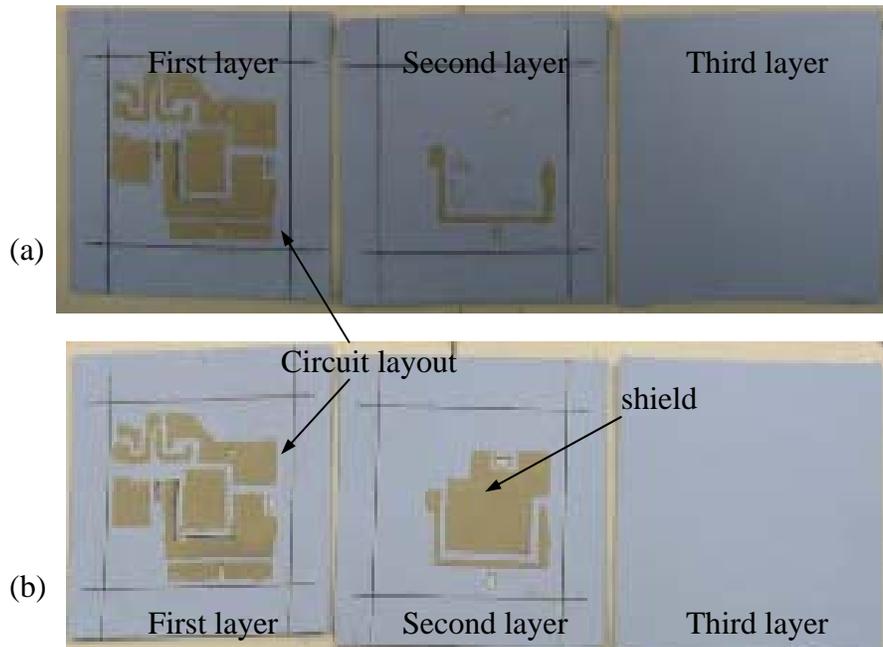


Figure 5-19 Trace layers for sample (a) with no shield and (b) with shield.

Figure 5-21 shows the waveforms at the switching point, V_{sw} , (see Fig. 5-1) of the Buck converter (V_{DS} of bottom switch) for sample (a) with no shield and (b) with shield at no load. The circuit is tested at a switching frequency of 1.3 MHz. The input voltage is 5 V and the output voltage is 1.1 V. The sample with no shield exhibit more severe voltage oscillations compared to the sample with shield. The low frequency voltage oscillations for the sample with no shield imply larger input loop inductance. The energy stored in the parasitic loop inductance is dissipated in the loop [128]. Hence, the larger the parasitic inductance, the larger the energy dissipated.

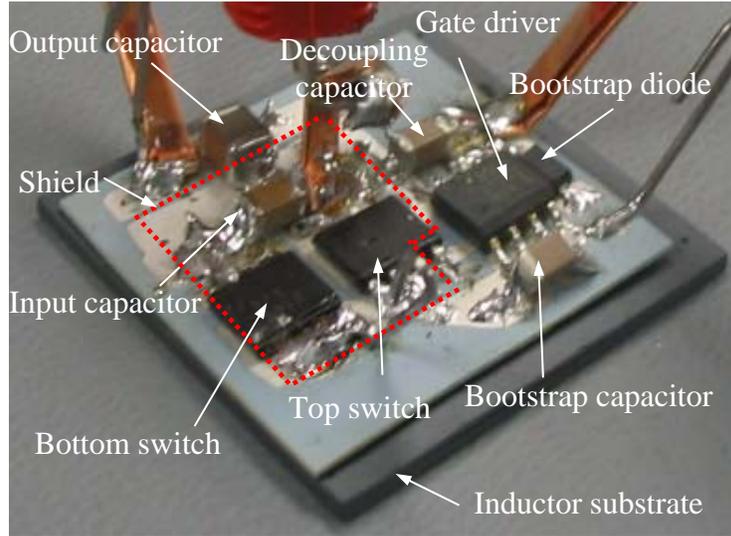


Figure 5-20 Improved prototype Buck converter with inclusion of metal shield above magnetic substrate. The red dotted line shows the shape of the metal shield, which is below the circuitry.

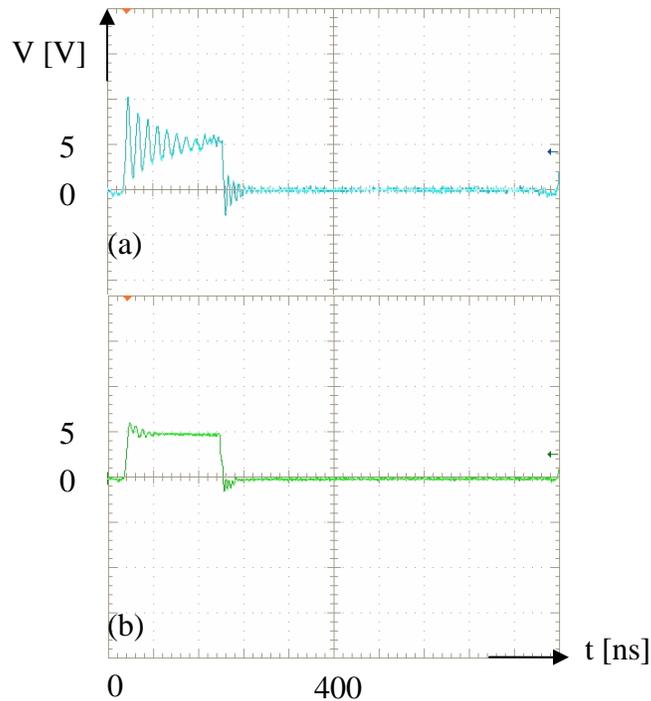


Figure 5-21 Waveforms of V_{DS} of bottom MOSFET in Buck converter for sample with (a) no shield and (b) with shield, at no load.

Figure 5-22 shows the power stage efficiency vs. I_{out} for the two samples with and without shield. The power stage efficiency is obtained by the ratio of the DC output power to DC input power. It is observed that the sample with no shield yields lower efficiency than the one with shield.

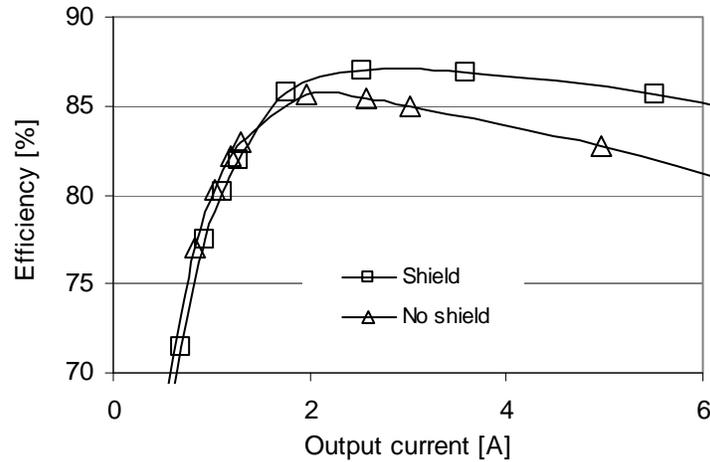


Figure 5-22 Power stage efficiency vs. output current for sample with shield and without shield, measured according to the methods of the circuits in Fig. 5-9.

In summary, an inductor fabricated using LTCC technology is used as a substrate where the traces are printed and devices mounted on the surface. The presence of a magnetic substrate below the circuitry creates additional parasitic inductances, which results in large magnitude and low frequency oscillations. The effect of the presence of a conductive shield helps to reduce trace inductance and improve circuit performance. Appropriate shield conductivity is necessary to lower the trace inductance and minimize power loss. Traces should be placed close to the shield to minimize inductance. Larger power loss is incurred in the sample with no shield.

5.8 Experimental Study of Substrate Structures

The popularity of portable devices makes size reduction of converters necessary to decrease the dimensions of the overall system. In a dc-dc converter, the bulkiest components are the capacitors and the inductors. Several companies that specialize in the development of power ICs with inductors-in-package have expanded their portfolio into buck regulators [129-132]. Several of these regulators make use of an inductor, which is essentially a copper spiral sandwiched between two magnetic cores [133]. These inductors are mostly co-packaged side-by-side with the buck converter semiconductor devices, but this increases the footprint. Table 5-4 shows some of the commercial buck regulators available on the market with integrated inductors and load currents in the ampere range [133].

Using the inductor as the substrate carrying the semiconductor and the other electronic components has been proposed as a means to reduce the overall footprint and to increase the power density of the converter [134-137]. A low-profile LTCC inductor substrate using NiCuZn ferrite material for micro dc-dc converters has been developed in [138] and [139]. In 2007 and 2008, Fuji Electric Technology and National Semiconductor released the FB6831J [140] and LM3218 [141] buck regulators integrating the inductor as a substrate. Both products are targeted at applications with current in the hundreds of mA range. An embedded inductor using spin-sprayed NiZn ferrite film in polymer substrate has also been developed [142].

Table 5-4 Commercial Buck Regulators with Integrated Inductor and Load Currents in
The Ampere Range [133]

Model	Input Voltage (V)	Output Voltage (V)	Current (A)	Switching Frequency (MHz)	Inductor	Package Size (mm)
Enpirion EN5360D (2 nd gen part)	2.375 to 5.5	0.8 to 3.3	6	5	Copper spiral on ferrite	8.1 × 17 × 2.2, DFN48
Enpirion EN5336Q (2 nd gen part)	2.375 to 5.5	0.8 to 3.3	3	5	Copper spiral on ferrite	7.5 × 10 × 1.85, QFN44
Micrel SuperLNR MIC38300	3.0 to 5.5	as low as 1.0	3	Not specified	Not specified	4 × 6 × 0.9, 28-pin MLF
Linear Technology LTM4600 DC/DC μ Module	4.5 to 20 (or 28 V)	0.6 to 5	10 A cont., 14 A peak	0.850, typ. at full load	Shielded low-profile inductor	15 × 15 × 2.8, LGA
Linear Technology LTM4601/02/03 DC/DC μ Module	4.5 to 20 (or 28)	0.6 to 5	6 A or 12 A, parallel for higher current	0.850, typ. at full load	Shielded low-profile inductor	15 × 15 × 2.8, LGA
Linear Technology LTM4604 μ Module	2.35 to 5.5	0.8 to 5	4	1.25	Shielded low-profile inductor	15 × 9 × 2.3, LGA
National Semiconductor LM3218 (2008)	2.7 to 5.5	0.8 to 3.6	0.5	2	Substrate	3 x 2.5 x 1.2
Fuji Electric Technology FB6831J (2007)	2.7 to 5.5	Min 0.8	0.5	2.5	Substrate	2.95 x 2.4 x 1.0

As the conductive traces are placed in proximity to the magnetic substrate, however, trace inductances increase, adversely affecting circuit operation especially at high currents. To mitigate the effect of the presence of a magnetic substrate, a conductive shield is introduced in section 5.7, which helps to reduce the overall trace inductance, in turn reducing switching losses in the active devices.

It is of interest to compare the difference in performance between placing the inductor side-by-side with the active circuit and using the inductor as a substrate to the active circuitry. The trade offs in performance with form factor is an area which is not yet explored. With the introduction of the shield, using a grounded shield and a floating

shield are compared to see the impact of grounding the shield. In addition, to observe the impact of using inductor as a substrate in the absence of a shield, the performance of samples with no shield using inductor as substrate and placing inductor side-by-side are also compared. Table 5-5 tabulates the various cases under comparison.

Table 5-5 Comparison of Cases with Substrate Inductor and Co-packaged Inductor.

	A. Inductor as substrate	B. Inductor side-by-side with actives
1	Actives layer with grounded shield	Actives layer with grounded shield
2	Actives layer with floating shield	Actives layer with floating shield
3	Actives layer without shield	Actives layer without shield

In the previous section, LTCC insulator material is used as the carrier for the active devices. However, since the insulator material is currently not co-fireable with the LTCC ferrite tape, it is necessary to fire them separately. The brittleness of the ceramic and the thickness of the carrier with integrated shield and circuit layout being less than 150 μm makes it difficult to handle. Hence, pyralux⁵ [143] is used as an alternative solution for this comparison. The organic insulator has a thickness of 50 μm . The copper layers have a thickness of 70 μm each. Fig. 5-23 (a) shows the 3-D view of surface mount devices and components, with pyralux carrier and substrate inductor. Fig. 5-23 (b) shows the 2-D lay-up diagram of pyralux carrier and substrate inductor.

⁵ Pyralux - organic insulator with copper sheets adhered to both sides

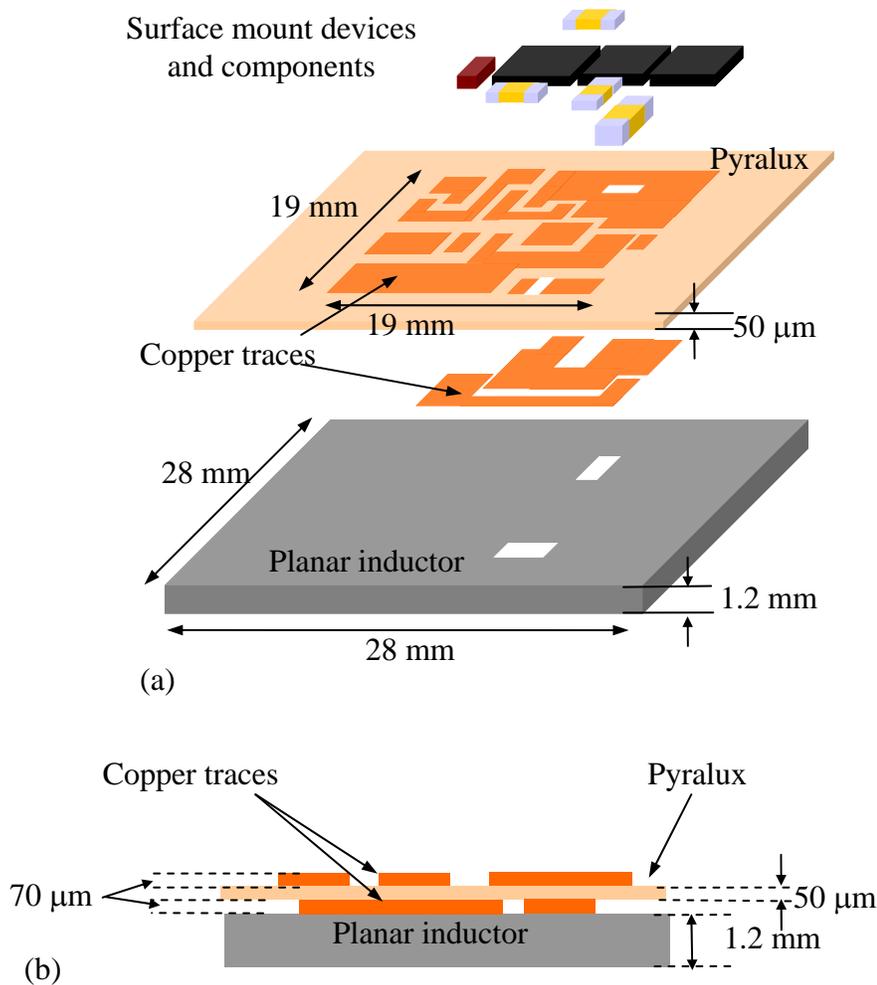
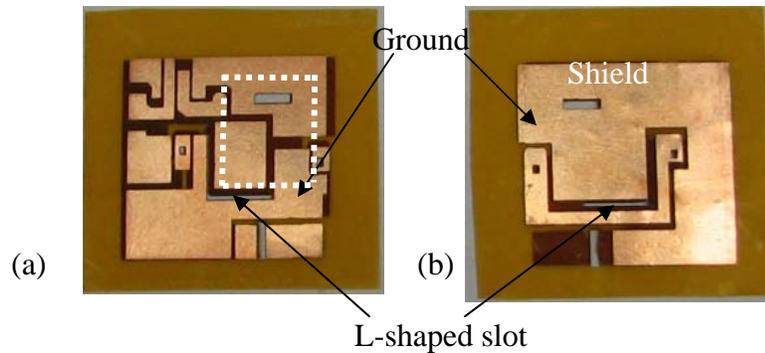


Figure 5-23 Surface mount devices and components, with pyralux carrier and substrate inductor. (a) 3-D view (b) 2-D lay-up diagram of pyralux carrier and substrate inductor.

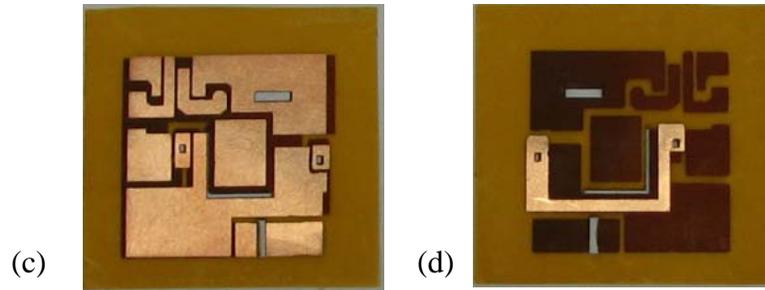
5.8.1 Samples Fabrication Procedure

The fabrication procedure of the inductor used for this set of experiments is the same as that described in Fig. 5-18. The layer which contains the circuit layout where the components and devices are soldered on is fabricated using pyralux [143], which is essentially a layer of organic material sandwiched by copper sheets on both sides. The pyralux has a layer of copper with thickness of 70 μm on both sides. The organic layer is 50 μm .

The starting material is a 28 mm x 28 mm pyralux. A piece of Kapton tape is pasted on both sides of the pyralux. The circuit layout pattern is cut on the Kapton layer using laser. The same is done for the rest of the circuitry on the reverse side. The Kapton layer on top of the copper which is to be etched is peeled off using a tweezer. The sample is then etched using ferric chloride solution. Fig. 5-24 (a) and (b) show the top layer and reversed layer of pyralux for the samples with shield. Fig. 5-24 (c) and (d) show that for the sample without shield.



(a) Top layer of pyralux showing circuit layout, (b) flipped layer of pyralux showing shield and part of circuit layout for sample with shield.



(c) Top layer of pyralux showing circuit layout, (d) flipped layer of pyralux with part of circuit layout for sample without shield.

Figure 5-24 Pyralux layer with circuit layout on top layer, with and without shield on flipped layer.

Each pyralux active carrier is tested using the LTCC inductor as a substrate and as a co-packaged inductor. For the sample where the shield is grounded, a piece of copper

foil is used to connect the ground on the top layer to the shield on the reverse side of the pyralux via the L-shaped slot (see Fig. 5-24 (a) and (b)) in order to have negligible impedance at 1.3 MHz. For the sample where the shield is floating, there is no electrical connection between the shield and the ground on the top layer.

5.8.2 Experimental Prototypes

The three 5 V - to - 1.1 V, 20 A buck converter prototypes operate at 1.3 MHz. The three prototypes are (a) active circuitry with grounded shield, (b) active circuitry with floating shield and (c) active circuitry with no shield. The surface mount devices and capacitors are soldered onto the pyralux carrier, and the LTCC planar inductor is then electrically connected to the pyralux active carrier. Table 5-6 tabulates the parts used in the fabrication of the prototype.

Table 5-6 Parts Used In Fabrication of Prototype.

Part	Part Number	Attributes
Q_{top}	RJK0301DPB [144]	$R_{ds,on}=8.8\text{ m}\Omega, V_{DSS}=30\text{ V}, Q_{gd}=2.4\text{ nC}, \text{SO8}$
Q_{bot}	RJK0301DPB [144]	$R_{ds,on}=3.3\text{ m}\Omega, V_{DSS}=30\text{ V}, Q_{gd}=7.1\text{ nC}, \text{SO8}$
Gate driver	LM27222 [140]	$t_{pd}=8\text{ ns}, t_{dead_time}=10\text{ ns}, V_{in}=4\text{ to }6.85\text{ V}$
C_1, C_2	ECJ-3YB1E105K	1 μF , 25 V
C_{in}	-	10 μF , 15 V
C_o	ECJ-4YB0J107M	100 μF , 6.3 V
D_1	MBR130T1 [123]	30 V, 1 A, SOD123, Schottky diode

When the inductor is used as a substrate, the pyralux layer with the active circuitry is connected to the inductor by placing it on top of the inductor, as shown in Fig. 5-25 (a). When the active circuitry is co-packaged with the inductor, the active circuitry is placed by the side of the inductor, as shown in Fig. 5-25 (b).

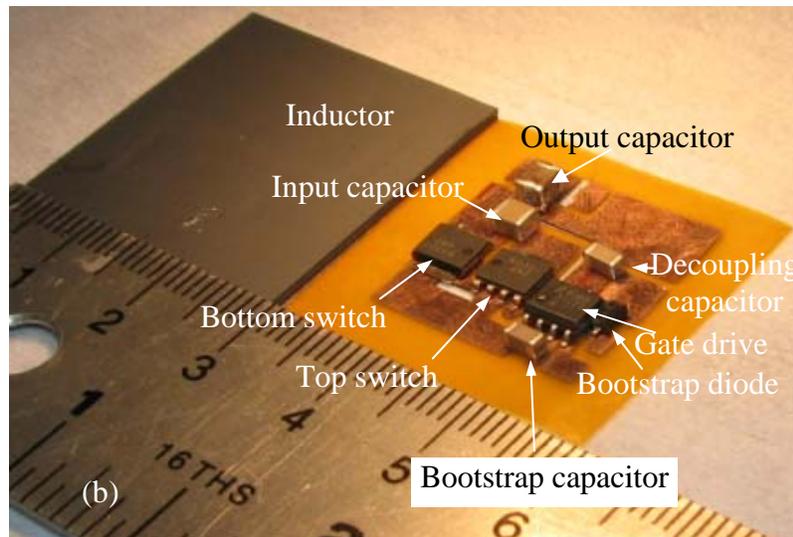
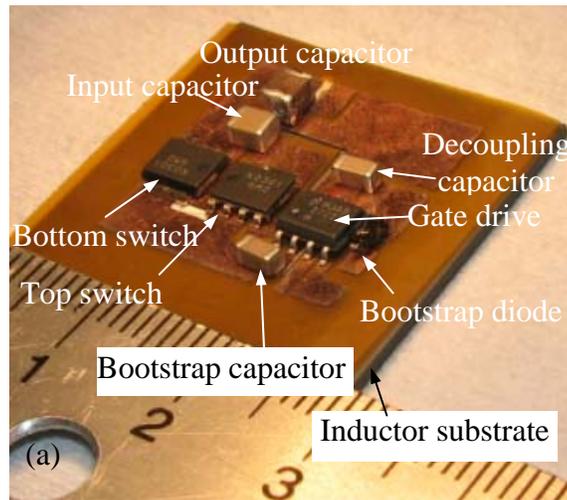


Figure 5-25 Prototype buck converter with integrated shield and inductor (a) as substrate, (b) inductor placed on the side of active circuitry.

The same inductor is used for all six test cases. Since the active circuitry is connected to the inductor via thick copper straps for the cases using the co-packaged inductor, the

copper straps introduced additional inductance to the circuit. The effective inductance is measured using the ratio of the voltage across the inductor and the slew rate of the inductor current during the time when the top switch is off, as shown in Box A in Fig. 5-26. Figure 5-27 shows the plot of inductance vs. I_{out} for the six cases. From Fig. 5-27, it can be concluded that the copper straps introduced around 20 nH to 40 nH of additional inductance when comparing the graphs of inductance vs. I_{out} for inductor placed side-by-side with active circuitry (co-packaged) and inductor used as substrate.

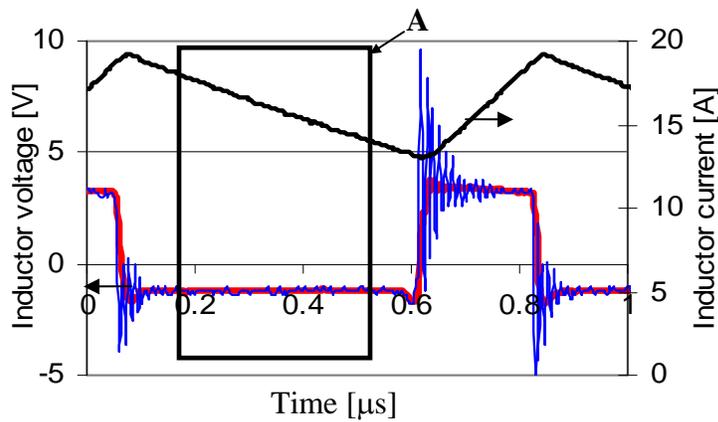


Figure 5-26 Inductor voltage and current waveforms.

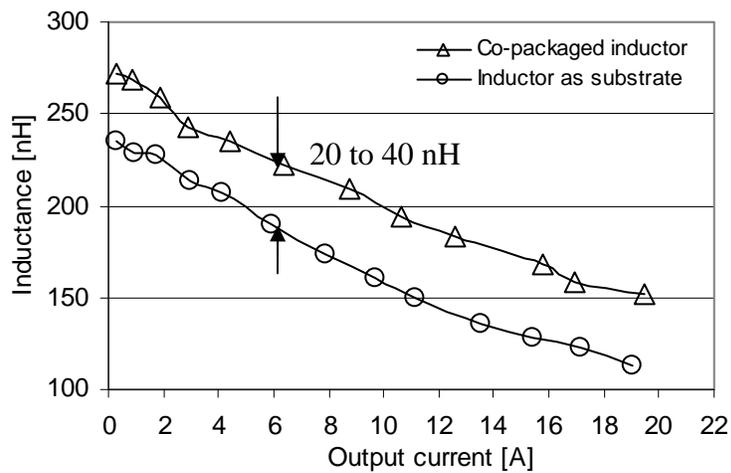
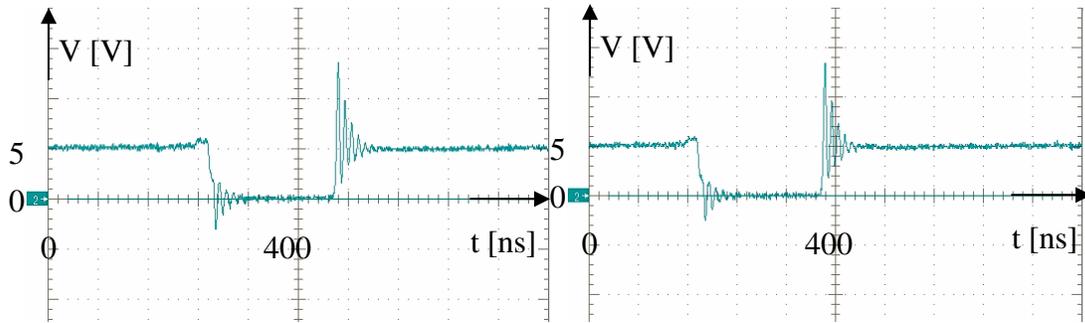


Figure 5-27 Inductance vs. output current for the case of inductor side-by-side with the active circuit and inductor as substrate to the active circuit.

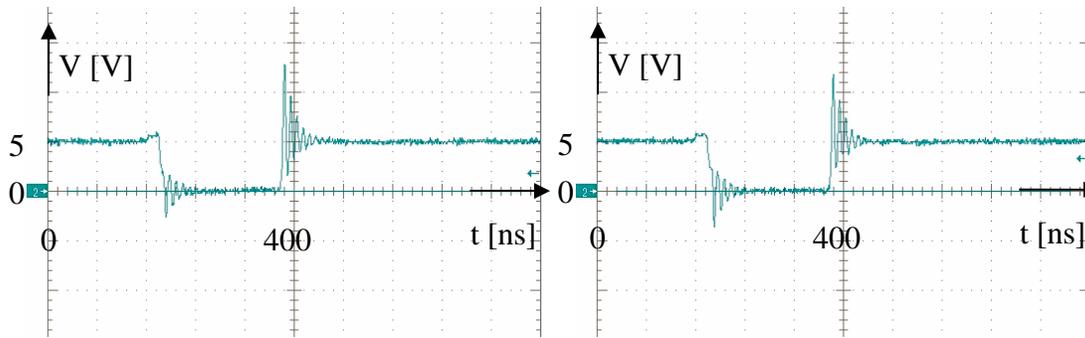
5.8.3 Metrics Comparison

The metrics used for comparison are percentage overshoot across the MOSFETs, the ringing frequency, the switching loss, and the power stage efficiency. To obtain the voltage overshoot and the switching loss, the voltage waveforms across the top and bottom MOSFETs are obtained for the six cases. Figure 5-28 shows the voltage waveforms across the top MOSFET and Fig. 5-29 shows that for the bottom MOSFET for the six cases in Table 5-5.



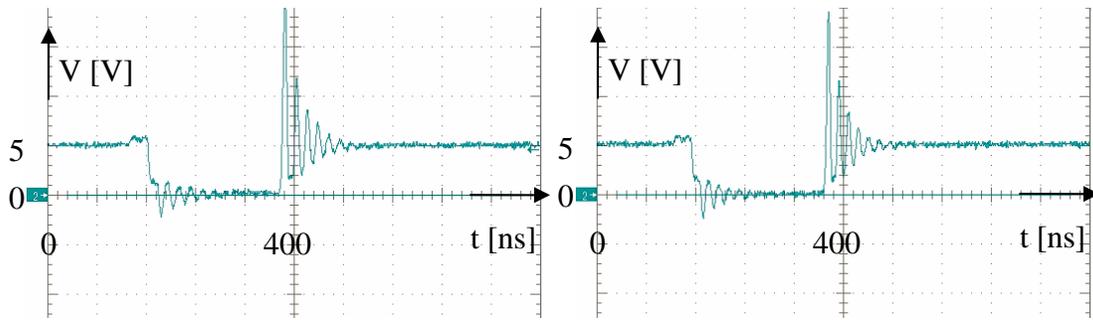
(a) Inductor as substrate with grounded shield

(b) Inductor on the side with grounded shield



(c) Inductor as substrate with floating shield

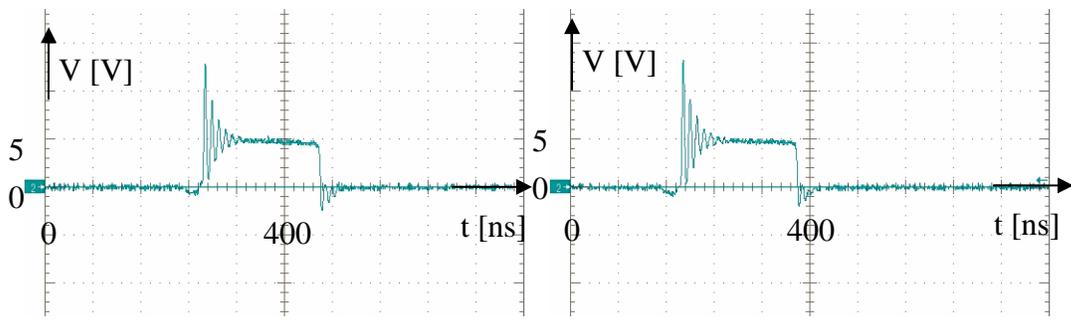
(d) Inductor on the side with floating shield.



(e) Inductor as substrate with no shield

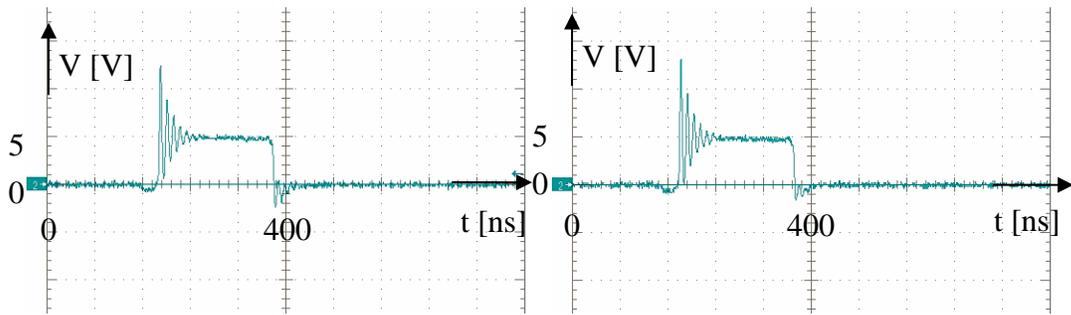
(f) Inductor on the side with no shield

Figure 5-28 V_{DS} of top MOSFET for the six cases. The frequency is 1.3 MHz and the average current is around 16 A.



(a) Inductor as substrate with grounded shield

(b) Inductor on the side with grounded shield



(c) Inductor as substrate with floating shield

(d) Inductor on the side with floating shield.

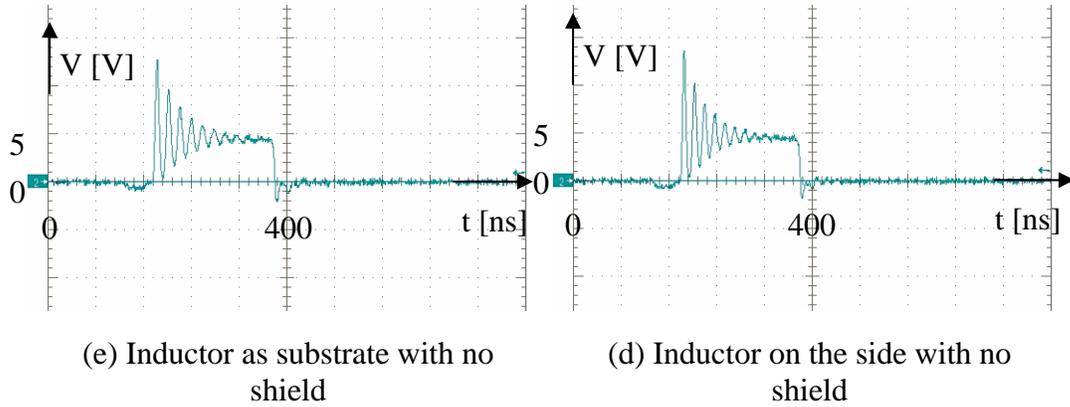


Figure 5-29 V_{DS} of bottom MOSFET for the six cases. The frequency is 1.3 MHz and the average current is around 16 A.

5.8.3.1. Voltage overshoot comparison

The impact of the presence of an inductive substrate and the effect of shielding can manifest itself in the form of voltage overshoot. This will determine the voltage rating of the devices required. Table 5-7 tabulates the voltage overshoot and normalized voltage overshoot across the top and bottom MOSFETs for each of the six cases.

Table 5-7 Voltage Overshoot Comparison.

Sample	Description	V_{top}	V_{bot}	$V_{top,n}$	$V_{bot,n}$
A1	Actives layer with grounded shield with inductor as substrate	8.8	7.8	1.000	1.000
A2	Actives layer with grounded shield using co-packaged inductor	7.9	8.2	0.898	1.051
B1	Actives layer with floating shield with inductor as substrate	8	7.5	0.909	0.962
B2	Actives layer with floating shield using co-packaged inductor	6.9	8	0.784	1.026
C1	Actives layer without shield with inductor as substrate	15.2	7.8	1.727	1.000
C2	Actives layer without shield using co-packaged inductor	13.7	7.8	1.557	1.000

The voltage overshoot observed in Fig. 5-28 is relatively high compared with that in Fig. 5-21 because in Fig. 5-21, the waveforms are obtained at no load, whereas in Fig. 5-28, the load current is 16 A.

From Table 5-7, the voltage overshoot across the top MOSFET is significantly higher for the cases where there is no shield. MOSFET voltage rating greater than 20 V is required for the top MOSFETs if no shield is used. For the cases with shield, MOSFETs with voltage rating of 20 V would suffice for a load current of 16 A.

5.8.3.2. Parasitic inductance

The parasitic loop inductance in the input loop acts as an energy storage center and this energy is dissipated in the loop via the trace resistances and resistances in the switches. This power loss leads to degradation of performance of the circuit in the form of decreased efficiency. The loop inductance can be calculated using

$$f_r = \frac{1}{2\pi\sqrt{L_{loop}C_{oss}}} \quad (5-12)$$

where f_r is the frequency of oscillation of the voltage waveform of the MOSFET, L_{loop} is the input loop inductance, and C_{oss} is the output capacitance of the MOSFETs. f_r is calculated using the first three oscillations in the voltage across the top MOSFET. C_{oss} is taken to be 1450 pF from the datasheet [144]. The power dissipated is calculated using

$$P = \frac{1}{2} L_{loop} \cdot i^2 \cdot f \cdot 2 \quad (5-13)$$

where L_{loop} is the loop inductance, f is the switching frequency, 1.3 MHz. The 2 at the end of the equation represents turn on and turn off within a cycle. Table 5-8 tabulates the loop inductance and power loss comparison at $I_{out} = 16$ A.

It is clear that the presence of a shield dramatically reduces the input loop inductance and the power loss due to energy storage in the input loop. The cases with floating shield have a slightly lower loop inductance and power loss than the case with grounded shield. This could be because the shield when grounded is affected by any perturbations in the ground. The shield reduces parasitic inductance by inducing an opposing current in itself which helps to cancel the magnetic field caused by the trace on top. Any perturbations in the ground may affect the effectiveness of the shield.

Table 5-8 Loop Inductance and Power Loss Comparison At $I_{out} = 16$ A.

Sample #	f_r [MHz]	L_{loop} [nH]	P [W]
A1	91.74	2.08	0.691
A2	91.13	2.10	0.700
B1	96.65	1.87	0.622
B2	98.75	1.79	0.596
C1	55.4	5.69	1.894
C2	60.44	4.78	1.592

Figure 5-30 shows the comparison of loop inductance for the inductance obtained from simulation and that derived from experimental results for the four cases. The general trend between the simulation and experiment is similar. For instance, case B has a higher loop inductance than case A, and cases C and D have lower loop inductances than cases A and B. The difference in inductances among the cases is greater in the simulation compared with that derived from the experiments. In the simulation, the loop

inductance is derived from the current flowing in the copper sheet in Fig. 5-11. However, in actual experiments, the current will be flowing through the packaged MOSFETs, which were soldered to the copper trace shown in Fig. 5-24(a). The different current distribution in the MOSFET and in the package may contribute to the differences in the inductances obtained. Besides, the inductances for the experiments are estimated based on the datasheet value of the C_{oss} of the MOSFET. The change in the C_{oss} of the MOSFET with voltage can cause differences in the inductance calculated.

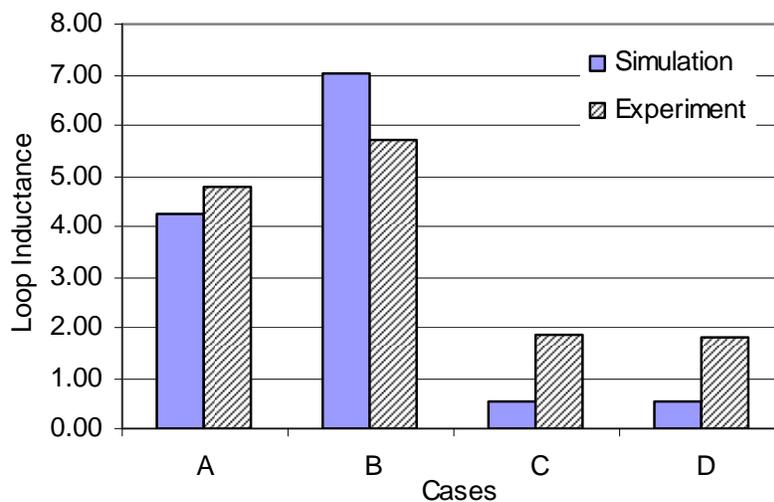


Figure 5-30 Loop inductance comparison for inductance obtained from simulation and derived from experimental results for the four cases.

The experimental result in Case B (circuit on inductor substrate without a shield) shows a lower inductance compared with simulation. This is because in actual experiments, the distance between the pyralux carrier and the inductor substrate was larger compared to the ideal case in simulations, due to soldering as well as the pyralux itself being a flexible material. Any change in distance (in the sub millimeter range) between the pyralux carrier and the inductor substrate can cause a difference in the loop

inductance. As a result, the effect of the inductor substrate may not as pronounced in the actual case due to the larger distance between the inductor substrate and the pyralux carrier. In addition, any small difference in the placement of the input capacitor, as well as the distance between the two MOSFETs can cause a difference in the physical loop size, which will affect the loop inductance.

5.8.3.3 Efficiency

The power stage efficiency is compared for the six cases. Figure 5-31 (a) shows the graph of efficiency vs. I_{out} . The efficiency curves are relatively close for the cases with grounded and floating shield, using the substrate inductor or co-packaged inductor. The efficiency is appreciably higher for the four cases with shield, both using substrate inductor and co-packaged inductor, compared with the two cases with no shield. The circuit with no shield on inductor substrate has the lowest efficiency. Its efficiency at 16 A is around 5-7 % lower than the cases with shield. The case of circuit with no shield co-packaged with inductor is slightly lower than the cases with shield. The cases with floating shield have slightly higher efficiency compared with the cases with grounded shield. The possible reason was mentioned in the previous section. For the cases with shield, the circuit with co-packaged inductor shows slightly higher efficiency than the cases with inductor as substrate. This is due to the higher output inductance seen by the circuit, which is due to the copper straps used for electrical connection.

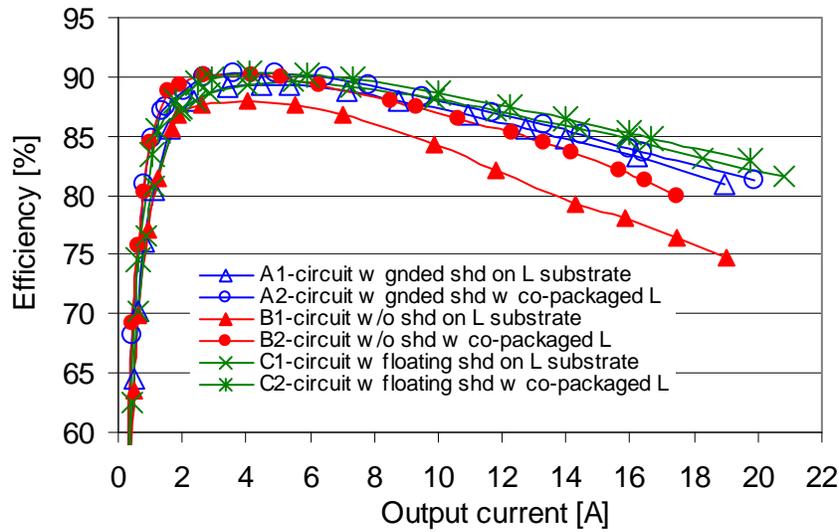


Figure 5-31 Power stage efficiency vs. I_{out} for the six cases.

5.8.3.4 Gate Drive Input Power

Table 5-9 tabulates the comparison of gate drive input power for the six cases. The gate drive input power is the power input to the gate drive circuit, which is provided by another power supply. The gate drive input power is significantly higher for the cases with no shield. The case of the circuit with no shield on inductor substrate exhibits the highest gate drive loss. The four cases with shield have similar gate drive loss.

From the experimental results, when the inductor is used as a substrate and in the absence of a shield, the loop inductance is increased, leading to higher losses. Losses in both the gate drive and the power stage are increased. Both power losses are shown to be reduced by introducing a shield below the active circuitry. The losses are relatively close when the inductor is used as a substrate or is co-packaged when there is a shield below the circuit traces. The cases with floating shield show a slightly higher efficiency than the cases with grounded shield.

Table 5-9 Gate Drive Loss Comparison at $I_{out} = 16$ A.

Sample #	P_G [W]
A1	0.5
A2	0.505
B1	0.495
B2	0.495
C1	0.61
C2	0.573

4.8.3.5 Summary

The introduction of a shield beneath the circuitry reduces trace parasitic inductances, which helps in reducing losses associated with switching. Switching loss is the highest in the absence of a shield and when the inductor is used as a substrate. Switching loss is reduced when the shield is grounded, regardless of whether the inductor is used as a substrate or is co-packaged. Circuit with floating shield demonstrates a slightly higher efficiency compared with the cases when the shield is grounded.

5.9 Summary

The use of the inductor as a substrate where the surface is populated by other devices and components, frees the surface real estate of the bulky magnetic component. However, the presence of a magnetic material below the circuitry increases parasitic inductances in circuit traces and adversely affects circuit performance. It is evident from

experimental results that the presence of an inductive substrate results in greater loop inductance and hence a poorly damped voltage oscillation across the devices, which can lead to operation when it is supposed to be turned off. This can lead to degradation in the overall efficiency of the converter. A conductive shield introduced between the magnetic substrate and the circuitry helps alleviate the impact of the magnetic substrate on circuit operation. Parasitic inductances, which cause voltage oscillations and overshoots across devices reduces with proximity between the shield and the circuitry. The shield thickness in the range of 50 μm to 100 μm is found to be a good compromise between power loss and parasitic inductance reduction. The shield is effective when its conductivity is above 10^7 S/m. Experimental results show a reduction in voltage oscillation and overshoot across the devices of the buck converter, reduction in input loop inductance, as well as an increase in efficiency when a shield is incorporated. Gate drive loss can also be reduced with the presence of a shield. Circuits with floating shields under it exhibit slightly better efficiency compared with when the shield is grounded. When an inductor is to be used as a substrate, a 5 % to 7 % improvement in efficiency can be obtained when a shield is incorporated.

Chapter 6. Conclusion and Further Work

6.1 Conclusion

Using LTCC technology for power electronic applications is a new area. It has not been thoroughly explored before, partly due to the limitations of the current LTCC processing technology for high-current applications, as well as a widespread interest in on-chip magnetics integration, which currently dominates low-power applications. The use of low temperature co-fired ceramics (LTCC) technology for power converter magnetics integration is developed to accommodate the requirement of fabricating magnetic samples with thick conductors for power applications.

Prior to the use of the ceramic magnetic material for making the inductors, electrical characterization is performed to understand the electrical behavior of the material and to understand its suitable regions of operation. A power loss empirical model based on the Steinmetz equation is developed to help in the estimation of losses at the targeted frequency range of 1 MHz to 4 MHz, an operating temperature between 25 °C and 70 °C, DC pre-magnetization from 0 A/m to 1780 A/m, and AC magnetic flux densities between 5 mT and 50 mT. Temperature and DC pre-magnetization dependence on Steinmetz exponents are included in the model to more accurately describe the loss behavior.

Various geometries are evaluated in the development of LTCC technology to fabricate chip inductors. An inductor with a short winding surrounded by magnetic material is desirable due to the requirement to conduct large currents. Conductor geometry is studied to select a suitable cross-sectional shape to obtain a smaller footprint as well as lower losses, and the LTCC process is modified to produce conductors of the

desired rectangular cross-sectional shape, as well as to enable the fabrication of magnetic components with thick conductors. Inductors with this geometry exhibit varying inductance with current, which helps improve the converter efficiency at light load. Parametric variation of the inductor geometry is performed in an effort to develop an empirical model to describe the change in inductance with DC current.

Using the inductor as the substrate, where its surface can be populated by the semiconductor and the other electronic components, is a next step to improving the power density. The negative impact of the presence of a magnetic substrate in close proximity to the circuitry can be mitigated by the introduction of a conductive shield between the circuitry and the magnetic substrate. Parasitic inductance is found to decrease with the decrease in distance between the shield and the circuitry. A shield thickness in the range of 50 μm to 100 μm is found to be a good compromise between power loss and parasitic inductance reduction. The effectiveness of the shield is apparent when its conductivity is above 10^7 S/m.

6.2 Further Work

The use of LTCC ceramic magnetic material shows promise for magnetics integration for power applications. In the materials and processing aspect, ferrite tapes of greater thicknesses can be casted, as opposed to laminating many layers of the tape. Conductive fillers like silver flakes or silver powder can be used for the conductor paste to improve the conductivity. Other inductor geometries in the form of a perforated plate inductor can be explored. The use of LTCC technology for making transformers for low-profile power adapter applications can be an extension of the current work. In addition, the extension of the work into the design and fabrication of coupled inductors for multi-phase converters is also a possible area of research.

Appendix

The parameters used in the equations below are with reference to Fig. A-1.

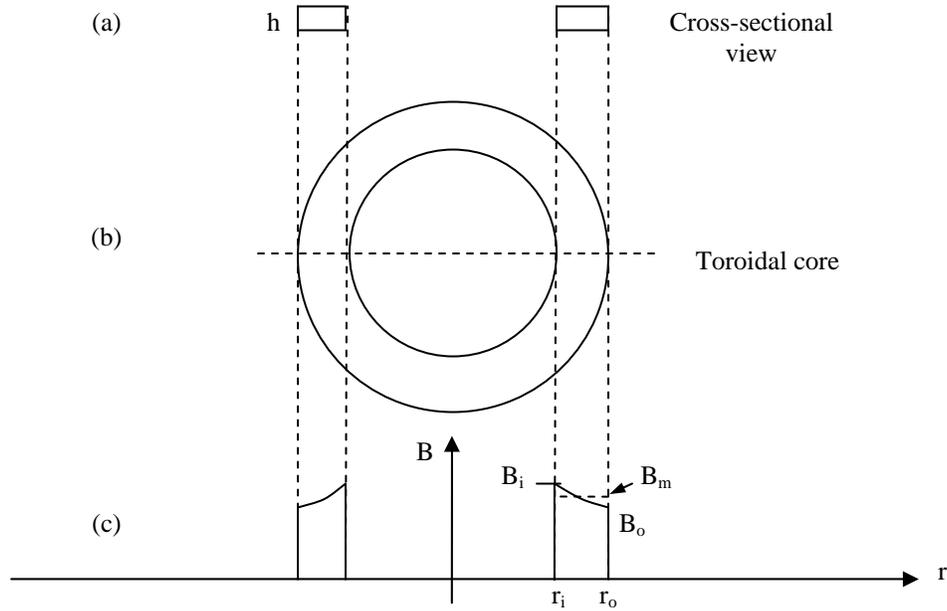


Figure A-1 Illustrations for derivations. (a) Cross sectional drawing, (b) plan view drawing and (c) magnetic flux density illustration for toroidal core.

The magnetic flux density can be expressed as:

$$B = \frac{\mu Ni}{2\pi r} \quad (\text{A-1})$$

The magnetic flux density at the inner radius and outer radius can be expressed as:

$$B_i = \frac{\mu Ni}{2\pi r_i} \quad (\text{A-2})$$

$$B_o = \frac{\mu Ni}{2\pi r_o} \quad (\text{A-2})$$

The average magnetic flux can be obtained using the analysis below:

$$\int_{r_i}^{r_o} B dr = B_m (r_o - r_i) \quad (\text{A-3})$$

$$\int_{r_i}^{r_o} B dr = \int_{r_i}^{r_o} \frac{\mu Ni}{2\pi r} dr \quad (\text{A-4})$$

Equating (A-3) with (A-4),

The average magnetic flux, B_m , can be expressed as:

$$B_m = \frac{\mu Ni}{2\pi r} \cdot \frac{[\ln(r_o) - \ln(r_i)]}{r_o - r_i} \quad (\text{A-5})$$

The specific power loss, using Steinmetz equation [79], can be expressed as:

$$P_v = K_p \cdot f^\alpha \cdot B^\beta \quad (\text{A-6})$$

Assuming frequency as a constant, the specific power loss can be expressed as:

$$P_v \propto B^\beta \quad (\text{A-7})$$

The power loss in the core can be expressed as:

$$P = \int P_v dV \quad (\text{A-8})$$

If magnetic flux density, B , is assumed to be a constant value of B_m , the power loss in the core, P_1 , can be expressed as:

$$P_1 \propto \int B^\beta d(\pi r^2 h)$$

$$P_1 \propto B^\beta \pi h [r_o^2 - r_i^2] \quad (\text{A-9})$$

If magnetic flux density, B , is assumed to be not a constant, the power loss in the core, P_2 , can be expressed as:

$$P_2 \propto \int B^\beta dV$$

$$P_2 \propto \int \left(\frac{\mu Ni}{2\pi r} \right)^\beta d(\pi r^2 h)$$

$$P_2 \propto \frac{2\pi h}{2-\beta} \left(\frac{\mu Ni}{2\pi} \right)^\beta [r_o^{2-\beta} - r_i^{2-\beta}] \quad (\text{A-10})$$

Reference

- [1] R. Kraus, H. J. Mattausch, "Status and trends of power semiconductor device models for circuit simulation", *IEEE Trans. Power Electron.*, vol. 13, no. 3, pp. 452 – 465, May 1998.
- [2] H. Ohashi, "Power electronics innovation with next generation advanced power devices", in *Proc. 25th Int. Telecommunications Energy Conf.*, Oct. 2003, pp. 9 – 13.
- [3] J. D. van Wyk, F. C. Lee, Z. Liang, R. Chen, S. Wang, B. Lu, "Integrating active, passive and EMI-filter functions in power electronics systems: a case study of some technologies", *IEEE Trans. Power Electron.*, vol. 20, no. 3, pp. 523 – 536, May 2005.
- [4] J.D. van Wyk, J.T. Strydom, L. Zhao, R. Chen, "Review of the development of high density integrated technology for electromagnetic power passives", in *Proc. IEEE 2nd Int. Conf. Integrated Power Systems*, 2002, pp. 25-34.
- [5] J. Ferrell, J. –S. Lai, T. Nergaard, X. Huang, L. Zhu, R. Davis, "The role of parasitic inductance in high-power planar transformer design and converter integration", in *Proc. Appl. Power Electron. Conf.*, 2004, vol. 1, pp. 510 – 515.
- [6] Z. Liang, J. D. van Wyk, F. C. Lee, D. Boroyevich, "An integrated power switching stage with multichip planar interconnection construction", in *Proc. 4th Int. Power Electron. and Motion Control Conf.*, 2004, vol. 1, pp. 364 – 369.
- [7] L. Li, P. Bowles, L. T. Hwang, S. Plager, "Embedded passives in organic substrate for bluetooth transceiver module", in *Proc. 53rd Electronic Components and Technology Conf.*, 27-30 May, 2003, pp. 464 - 469
- [8] S. Stalf, "Printed inductors in RF consumer applications", in *Proc. Int. Conf. on Consumer Electronics.*, 19-21 June 2001 pp. 102 – 103.
- [9] S. Dalmia, J. M. Hobbs, V. Sundaram, M. Swaminathan, Seock Hee Lee, F. Ayazi, G. White, S. Bhattacharya, "Design and optimization of high Q RF passives on SOP-based organic substrates", in *Proc. 52nd Electronic Components and Technology Conf.*, 28-31 May 2002, pp. 495 – 503.
- [10] C. T. Chiu, C. L. Lin, T. S. Horng, S. M. Wu, C. P. Hung, "Design of Miniature Bandpass Filters Embedded in the Organic Substrate for RF SOP Applications", in *Proc. 36th European Microwave Conf.*, Sept. 2006 pp. 502 – 505.
- [11] H. Tsujimoto, O. Ieyasu, "High frequency transmission characteristic of co-planar film transformer fabricated on flexible polyamide film", *IEEE Trans. Magnetics.*, vol. 31, no. 6, part 2, Nov. 1995, pp. 4232 – 4234.
- [12] X. Sun, D. Linten, O. Dupuis, G. Carchon, P. Soussan, S. Decoutere, W. De Raedt, "High-Q on-chip inductors using thin-film wafer level packaging technology demonstrated on a 90 nm RF-CMOS 5 GHz VCO", in *Proc. European Microwave Conf.*, vol. 1, 4-6 Oct. 2005.
- [13] Chen Yang, Feng Liu, Tian-Ling Ren, Li-Tian Liu, Guang Chen, Xiao-Kang Guan, Wang, A., Hai-Gang Feng, "Ferrite-Integrated On-Chip Inductors for RF ICs", *IEEE Electron Dev. Lett.*, vol. 28, no. 7, pp. 652 – 655, July 2007.

- [14] W. Bakalski, N. Ilkov, O. Dernovsek, R. Matz, W. Simburger, P. Weger, A. L. Scholtz, "5-6.5 GHz LTCC power amplifier module with 0.3 W at 2.4 V in Si-bipolar", *Electronics Lett.*, vol. 39, no. 4, pp. 375 – 376, 20 Feb 2003.
- [15] D. Heo, A. Sutono, E. Chen, Y. Suh and J. Laskar, "A 1.9-GHz DECT CMOS Power Amplifier with Fully Integrated Multilayer LTCC Passives", *IEEE Microwave and Wireless Components Lett.*, vol. 11, no. 6, pp. 249 - 251, Jun 2001.
- [16] M. Saidani, M. A. M. Gijs, "Hybrid flex foil-ferrite technology for miniaturized power and RF applications", in *Proc. IEEE Int. Symp. Industrial Electronics*, vol. 1, 4-7 May 2004, pp. 23 - 26.
- [17] T. Fujiwara, "Planar integrated magnetic component with transformer and inductor using multilayer printed wiring board", *IEEE Trans. Magnetism*, vol. 34, no. 4, part 1, July 1998, pp. 2051 – 2053.
- [18] E. Waffenschmidt, B. Ackermann J. A. Ferreira, "Design method and material technologies for passives in printed circuit Board Embedded circuits", *IEEE Trans. Power Electron.*, vol. 20, no. 3, pp. 576 – 584, May 2005.
- [19] M. Ludwig, M. Duffy, T. O'Donnell, P. McCloskey, P, S. C. O. Mathuna, "PCB integrated inductors for low power DC/DC converter", *IEEE Trans. Power Electron.*, vol. 18, no. 4, pp. 937 – 945, July 2003.
- [20] M. Ludwig, M. Duffy, T. O'Donnell, P. McCloskey, P, S. C. O. Mathuna, "Design study for ultraflat PCB-integrated inductors for low-power conversion applications", *IEEE Trans. Magnetism*, vol. 39, no. 5, part 2, pp. 3193 – 3195, Sept. 2003.
- [21] R. Hahn, S. Krumbholz, H. Reichl, "Low profile power inductors based on ferromagnetic LTCC technology" in *Proc. 56th Electronic Components and Technology Conf.*, 30 May-2 June 2006, pp. 528-533.
- [22] P. Dhagat, Satish Prabhakaran, Charles R. Sullivan, "Comparison of magnetic materials for V-groove inductors in optimized high-frequency DC-DC converters", *IEEE Trans. Magnetism*, vol. 40, no. 4, part 2, pp. 2008 – 2010, July. 2004.
- [23] M. Rascon, R. Prieto, O. Garcia, J. A. Cobos, J. Uceda, "Design of very low profile magnetic components using flex foils", *IEEE 28th Appl. Power Electronics Conf.*, 23-27 Feb. 1997, vol. 2, pp. 561 – 567.
- [24] Erik J. Brandon, Emily E. Wesseling, Vincent Chang, and William, B. Kuhn, "Printed microinductors on flexible substrates for power applications", *IEEE Trans. Compon., Packag. Manufact. Technol.*, vol. 26, no. 3, pp. 517-523, Sept. 2003.
- [25] T. Mikura, K. Nakahara, K. Ikeda, K. Furukuwa, K. Onitsuka, "New substrate for micro DC-DC converter", in *Proc. 56th Electronic Components and Technology Conf.*, 30 May-2 June 2006, pp. 1326-1330.
- [26] W. A. Roshen, R. L. Steigerwald, R. Charles, W. Earls, G. Claydon, C. F. Saj, "High efficiency, high density MHz magnetic components for a low profile converter", *IEEE Trans. Ind. Appl.*, vol. 31, no. 4, pp. 869 – 878, July-Aug. 1995.

- [27] K. W. Moon, S. H. Hong, H. J. Kim, J. Kim, "A fabrication of DC-DC converter using LTCC NiZnCu ferrite thick film", *Digests IEEE Int. Magnetics Conf.*, 4-8 April 2005, pp. 1109 – 1110.
- [28] Datasheets of LTCC tapes and conductor pastes of Electrosience Labs. [online] Available: <http://www.electrosience.com>
- [29] Magali Brunet, Terence O'Donnell, Laurent Baud, Ningning Wang, Joe O'Brien, Paul McCloskey, and Sean C. O'Mathuna, "Electrical performance of Microtransformers for DC-DC converter applications", *IEEE Trans. Magnetics*, vol. 38, no. 5, pp. 3174-3176, Sept. 2002.
- [30] J. Y. Park, J. U. Bu, "Packaging compatible microtransformers on a silicon substrate", *IEEE Trans. Adv. Packag.*, vol. 26, no. 2, pp. 160 – 164, May 2003.
- [31] M. Mino, T Yachi, A. Tago and K. Tanagisawa, "A new planar microtransformer for use in micro-switching-converters", *IEEE Trans. Magnetics*, vol. 28, no. 4, pp. 1969-1973, July 1992.
- [32] M. Mino, T. Yachi, A. Tago, K. Yanagisawa and K. Sakakibara, "Planar Microtransformer with monolithically-integrated rectifier diodes for micro-switching converters", *IEEE Trans. Magnetics*, vol. 32, no. 2, pp. 291-296, Mar 1996.
- [33] T. C. Neugebauer, D. J. Perreault, "Filters with inductance cancellation using printed circuit board transformers", *IEEE Trans. Power Electron.*, vol. 19, no. 3, pp. 591 – 602, May 2004.
- [34] M. Joao Rosario, F. Le-Strat, P. -F. Alleaume, J. Caldinhas Vaz, J. Schroth, T. Muller, J. Costa Freire, "Low cost LTCC filters for a 30GHz satellite system", in *Proc. 33rd European Microwave Conf.*, 7-9 Oct. 2003, vol. 2, pp. 817 – 820.
- [35] H. Khatri, L. E. Larson, D. Y. C. Lie, "On-chip monolithic filters for receiver interference suppression using bond-wire inductors", *Topical Meeting on Silicon Monolithic Integrated Circuits in RF Systems*, 18-20 Jan. 2006, pp. 166-169.
- [36] Kai Zoschke, Klaus Buschick, Katrin Scherpinski, Thorsten Fischer, Jurgen Wolf, Oswin Ehrmann, Rafael Jordan, Herbert Reichl, Franz-Josef Schmuckle, "Stackable Thin Film Multi Layer Substrates with Integrated Passive Components", in *Proc. Electronic Components and Technology Conf.*, 30 May – 2 Jun 2006, pp. 806-813.
- [37] C. Q. Scramton, J. C. Lawson, "LTCC technology: where we are and where we're going. II", *IEEE MTT-S Symp. on Technologies for Wireless Applications*, 21-24 Feb. 1999, pp. 193 – 200.
- [38] Rao Tummala, "Fundamentals of Microsystems Packaging", McGraw Hill Professional, 1st edition, May 2001.
- [39] EPCOS. (2001, Jan.) Ferrite Polymer Composite (FPC) Film. [Online] Available: http://www.epcos.de/inf/80/ap/e0_001_000.htm
- [40] Ning Zhu, "Planar Metallization Failure Modes in Integrated Power Electronics Modules", Ph.D. dissertation, Virginia Tech.

- [41] Wenduo Liu, "Alternative Structures for Integrated Electromagnetic Passives", Ph.D. dissertation, Virginia Tech.
- [42] M.A. Zampino, R. Kandukuri, W. K. Jones, "High performance thermal vias in LTCC substrates", Eighth Intersociety Conf. on Thermal and Thermomechanical Phenomena in Electronic Systems, 2002, 30 May-1 June 2002, pp. 179 – 185.
- [43] W.K. Jones, Yanqing Liu, Mingcong Gao, "Micro heat pipes in low temperature cofire ceramic (LTCC) substrates", IEEE Transactions on Components and Packaging Technologies, vol. 26, no. 1, March 2003, pp. 110 – 115.
- [44] L. Pergola, R. Gindera, D. Jager, R. Vahldieck, "An LTCC-Based Wireless Transceiver for Radio-Over-Fiber Applications", IEEE Trans. Microwave Theory and Techniques, vol. 55, no. 3, March 2007, pp. 579 – 587.
- [45] Jyh-Wen Sheen, "LTCC-MLC duplexer for DCS-1800", IEEE Trans. Microwave Theory and Techniques, vol. 47, no. 9, part 2, Sept. 1999, pp. 1883 – 1890.
- [46] I. Kowase, T. Sato, K. Yamasawa, Y. Miura, "A planar inductor using Mn-Zn ferrite/polyimide composite thick film for low-voltage, large-current DC-DC converter", digests of the IEEE International Magnetics Conference, 4-8 April 2005, pp. 223 – 224.
- [47] M. J. Prieto, A. M. Pernia, J. M. Lopera, J. A. Martin, F. Nuno, "Design and analysis of thick-film integrated inductors for power converters", *IEEE Trans. Ind. Appl.*, vol. 38, no. 2, pp. 543 – 552, March-April 2002.
- [48] Jun Chul Kim, Dongsu Kim, Hyun Min Cho, Jong Chul Park, Nam Kee Kang, "A front end module and a filter using LTCC technology with heterogeneous dielectrics", Ceramic Interconnect and Ceramic Microsystems Technology Conf., Apr. 2006, paper TP43, pp. 1-5.
- [49] Leszek Golonka, Tomasz Zawada, Henryk Rogouszczak, Karol Malecha, Michal Chudy, Dorata Stadnik, Artur Dybko, "Three-dimensional fluidic microsystem fabricated in low temperature co-fire ceramic technology", Ceramic Interconnect and Ceramic Microsystems Technology Conf., Apr. 2006, paper WA21, pp. 1-6.
- [50] J. M. English and M. G. Allen, "Wireless micromachined ceramic pressure sensors", in Proc. 12th IEEE Int. Conf. Micro Electro Mechanical Systems, 1999, pp. 511-516.
- [51] Feng Zheng, Hubert George, and W. Kinzy Jones, "Development of a multi-channel electron multiplier using LTCC/thick silver cofired structures", Ceramic Interconnect and Ceramic Microsystems Technology Conf., Apr. 2006, paper WA21, pp. 1-6.
- [52] K. Itoh, et al., "Integrated even harmonic type direct conversion receiver for WCDMA mobile terminals (invited paper)", Proc. Of 2002 RFIC Symp., pp 263-266.
- [53] L. Larson and D. Jessie, "Packaging designs for radio-frequency ICs", EE Times, Sept. 2003.
- [54] New Jersey Nanotechnology Consortium [online] Available: <http://www.njnano.org>
- [55] Wenxia Li and John J. Lannutti, "Curvature evolution in LTCC tapes and laminates", IEEE Trans. Components and Packaging Technologies, vol. 28, no. 1, pp. 149-156, Mar 2005.

- [56] T. Cheng and R. Raj, "Flaw generation during constrained sintering of metal-ceramic and metal-glass multilayer films", *J. Amer. Ceram. Soc.*, vol. 72, no. 9, pp. 1649 – 1655, 1989.
- [57] C. H. Hsueh and A. G. Evans, "Residual stress and cracking in metal/ceramic systems for microelectronics packaging", *J. Amer. Ceram. Soc.*, vol. 68, no. 3, pp. 120-127, 1985.
- [58] J.-H. Jean and C.-R. Chang, "Camber development during cofiring Ag-based low dielectric-constant ceramic package", *J. Mater. Res.*, vol. 12, no. 10, pp. 2743-2750, 1997.
- [59] B. Geller, B. Thaler, A. Fathy, M. J. Liberatore, H. D. Chen, G. Ayers, V. Pendrick, and Y. Narayan, "LTCC-M: a enabling technology for high performance multilayer RF systems", *Microwave J.*, vol. 42, no. 7, pp. 64-72, 1999.
- [60] G.-Q. Lu, R. C. Sutterlin, and T. K. Gupta, "Effect of mismatched sintering kinetics on camber in a low-temperature cofired ceramic package", *J. Amer. Ceram. Soc.*, vol. 76, no. 8, pp. 1907-1914, 1993.
- [61] S. -H. Lee, G. L. Messing, E. R. Twinaime, A. Mohanram, C. A. Randall, and D. J. Green, "Co-sintering of multilayer ceramics", *Key Eng. Mater.*, vol. 206-213, p. 257-260, 2002.
- [62] Datasheet for ESL 40010 [online]. Available: <http://www.electroscience.com>
- [63] R. E. Mistler and E. R. Twinaime, "Tape casting theory and practice", Westerville, OH: Amer. Cer. Soc., 2000.
- [64] <http://www.accumet.com/>
- [65] Datasheet for ESL 2312, [online]. Available: <http://www.electroscience.com>
- [66] Datasheet for ESL 953, [online]. Available: <http://www.electroscience.com>
- [67] Bosui Liu; Xun Gong; Chappell, W.J., "Layer-by-layer polymer stereolithography fabrication for three-dimensional RF components", *IEEE Int. Microwave Symposium Digest*, vol. 2, 6-11 June 2004, pp. 481 – 484.
- [68] B. W. Hakki and P. D. Coleman, "A dielectric resonator method of measuring inductive capacities in the millimeter range," *IEEE Trans. Microwave Theory Tech.*, vol. MTT-8, pp. 402-410, July 1960.
- [69] Hirofumi Kakemoto, Song-Min Nam, Satoshi Wada and Takaaki Tsurumi, "High-Frequency Dielectric Measurement Using Non-contact Probe for Dielectric Materials", *Jpn. J. Appl. Phys.* 45 (2006) pp. 3002-3006.
- [70] David V. Blackham, and Roger D. Pollard, "An Improved Technique for Permittivity Measurements Using a Coaxial Probe", *IEEE Trans. Instrumentation and Measurement*, vol. 46, no. 5, oct. 1997, pp. 1093 – 1099.
- [71] Yan Ye, Taijun Liu, Xingbin Zeng, Jiameing He, and Cevdet Akyel, "Accurate Permittivity Measurement Using the Cavity Perturbation Technique at ISM 5.8GHz Radio Band", *Int. Conf. Microwave and Millimeter Wave Technology*, 18-21 April 2007 pp. 1 - 4.

- [72] R. Linkous, A. W. Kelley, K. C. Armstrong, "An improved calorimeter for measuring the core loss of magnetic materials", in proc. Appl. Power Electron. Conf., vol. 2, 6-10 Feb. 2000, pp. 633 – 639.
- [73] D. Zhang, S. Birlasekaran, T. T. Sim, P. C. Hum Peng, "Ferrite core loss measurement with arbitrary wave excitation", Int. Conf. on Power System Technology, 2004, vol. 1, 21-24 Nov. 2004, pp. 564 – 567.
- [74] J. Zhang, G. Skutt, F. C. Lee, "Some practical issues related to core loss measurement using impedance analyzer approach", in proc. Appl. Power Electron. Conf., vol. 2, no. 0, part 2, 5-9 March 1995, pp. 547 – 553.
- [75] P.M. Gradzki and F.C. Lee, "High-Frequency Core Loss Characterization Technique Based on Impedance Measurement," in proc. High Frequency Power Conversion Conference, 1991, pp. 108-115.
- [76] CECC 25 300. Magnetic oxide cores for power application. Harmonized system of quality assessment for electronic components, sectional specification, 1981.
- [77] V. J. Thottuvelil, T. G. Wilson, Jr. H. A. Owen, "High-frequency measurement techniques for magnetic cores", IEEE Trans. Power Electron., vol. 5, no. 1, Jan. 1990, pp. 41 – 53.
- [78] H. Y. Chung, F. N. K. Poon, C. P. Liu, M. H. Pong, "Analysis of buck-boost converter inductor loss using a simple online B-H curve tracer", in proc. Appl. Power Electron. Conf., 6-10 Feb. 2000, vol. 2, pp. 640 – 646.
- [79] S. Mulder, Loss Formulas for Power Ferrites and their Use in Transformer Design. Eindhoven, The Netherlands: Philips, 1994.
- [80] <http://www.ferroxcube.com>
- [81] R. W. Erickson and D. Maksimovic, "Fundamentals of Power Electronics", 2nd Edition, Springer, Jan 2001.
- [82] W. J. Sarjeant, D. T. Staffiere, "A report on capacitors", in proc. Appl. Power Electron. Conf., 3-7 March 1996, vol. 1, pp. 12 – 17.
- [83] <http://www.arrl.org> - Hands-on Radio, Experiment #63 – About Capacitors
- [84] W. Liu, "Alternative Structures for Integrated Electromagnetic Passives", Ph. D. dissertation, Virginia Tech.
- [85] "The Effect of Probe Input Capacitance on Measurement Accuracy" Tektronix Technical Brief.
- [86] Instructions for Tektronix P5050, 10X, passive probe, 18 Oct 2001.
- [87] Instructions for Tektronix P6243, 1 GHz, 10X, active probe instructions.
- [88] Wolfgang Maichen, "Digital Timing Measurements, From Scopes and Probes to Timing and Jitter Series: Frontiers in Electronic Testing", vol. 33, 2006.
- [89] D. C. Jiles and D. L. Atherton, "Theory of ferromagnetic hysteresis," J. Magnetism Magn. Mater., vol. 61, pp. 48–60, 1986.

- [90] B. D. Coleman and M. L. Hodgdon, "A constitutive relation for rate independent hysteresis on ferromagnetically soft materials," *Int. J. Eng. Sci.*, vol. 24, no. 6, pp. 897–917, 1986.
- [91] F. Preisach, "Über die magnetische nachwirkung," *Zeitschrift Phys.*, pp. 277–302, 1935.
- [92] D. C. Jiles, "Frequency dependence of hysteresis curves in 'nonconducting' magnetic materials," *IEEE Trans. Magn.*, vol. 29, pp. 3490–3492, Nov. 1993.
- [93] Kenneth H. Carpenter, "Simple Models for Dynamic Hysteresis Which Add Frequency-Dependent Losses to Static Models", *IEEE Trans. Magn.*, vol. 34, no. 3, pp. 619–622, May. 1998.
- [94] Peter R. Wilson, J. Neil Ross, and Andrew D. Brown, "Modeling Frequency-Dependent Losses in Ferrite Cores", *IEEE Trans. Magn.*, vol. 40, no. 3, pp. 1537–1541, May. 2004.
- [95] M. L. Hodgdon, "Applications of a theory of magnetic hysteresis," *IEEE Trans. Magn.*, vol. 24, pp. 218–221, Jan. 1988.
- [96] I. D. Mayergoyz, "Dynamic Preisach models of hysteresis," *IEEE Trans. Magn.*, vol. 24, pp. 2925–2927, Sept. 1988.
- [97] G. Bertotti, "Dynamic generalization of the scalar Preisach model of hysteresis," *IEEE Trans. Magn.*, vol. 28, pp. 2599–2601, Sept. 1992.
- [98] A. Brockmeyer, "Experimental evaluation of the influence of DC-premagnetization on the properties of power electronic ferrites", in *proc. Appl. Power Electron. Conf.*, vol. 1, 3-7 March 1996, pp. 454 – 460.
- [99] H. Y. Chung, F. N. K. Poon, C. P. Liu, M. H. Pong, "Analysis of buck-boost converter inductor loss using a simple online B-H curve tracer", in *proc. Appl. Power Electron. Conf.*, 6-10 Feb. 2000, vol. 2, pp. 640 – 646.
- [100] J. Reinert, A. Brockmeyer, R. W. A. A. De Doncker, "Calculation of Losses in Ferro- and Ferrimagnetic Materials Based on the Modified Steinmetz Equation", *IEEE Trans. Industry Appl.*, vol. 37, no. 4, Jul/Aug 2001, pp. 1055-1061.
- [101] W. Ruythooren, E. Beyne, J.-P. Celis and J. De Boeck, "Integrated High-frequency inductors using amorphous electrodeposited Co-P Core", *IEEE Trans. Mag.*, 38(5), sept '02, pg 3498.
- [102] Srinivasan Iyengar, Trifon M. Liakopoulos and Chong H. Ahn, "A DC/DC Boost Converter Toward Fully On-Chip Integration Using New Micromachined Planar Inductors", *Proc. IEEE Power Electronics Specialists Conference*, vol. 1, pp. 72-76, April 1999.
- [103] H. Kurata, K. Shirakawa, O. Nakazima, K. Murakami, "Study of thin film micro transformer with high operating frequency and coupling coefficient", *IEEE Trans. Mag.*, 29(6), nov '93, pp. 3204.

- [104] Ahn, C.H.; Kim, Y.J.; Allen, M.G.; , " A fully integrated planar toroidal inductor with a micromachined nickel-iron magnetic bar", IEEE Trans. Component Packaging and Manufacturing Tech., vol. 17, no. 3, pp. 463-469, Sept. 1994.
- [105] Charles R. Sullivan and Seth R. Sanders, "Design of microfabricated transformers and inductors for high-frequency power conversion", IEEE Trans. Power Electron., vol. 11, no. 2, Mar '96, pp. 228.
- [106] H. Feng, G. Jelodin, K. Gong, R. Zhan, Q. Wu, C. Chen and A. Wang, "Super compact RFIC inductors in 0.18 μ m CMOS with copper interconnects", IEEE Radio Frequency Integrated Circuits Symposium, 2002, pp. 443.
- [107] Eberhard Waffenschmidt, J.A. Ferreira, "Embedded passives integrated circuits for power converters", in proc. Power Electron. Specialists Conf. , 2002, pp. 12.
- [108] Chong H. Ahn and Mark G. Allen, "A Planar micromachined spiral inductor for integrated magnetic microactuator applications", J Micromech. Microeng. 3, 1993, pp. 37-44.
- [109] M. Yamaguchi, K. Ishihara and K. I. Arai, "Application of Thin-film inductors to LC filters", IEEE Trans. Mag., 29(6), nov '93, pp. 3222.
- [110] Musunuri, S.; Chapman, P.L.; Jun Zou; Chang Liu, "Design issues for monolithic DC-DC converters", IEEE Trans. Power Electron., vol. 20, no. 3, pp. 639 – 649, May 2005.
- [111] Hiroaki Tsujimoto and Ieyasu O, "High Frequency Transmission Characteristic of Co-planar Film Transformer Fabricated on Flexible Polyamide Film", IEEE Trans. Mag., 31(6), Nov. 95, pp. 4232.
- [112] Gustavo J. Mehas, Kip D. Coonley, Charles R. Sullivan, "Design of microfabricated inductors for microprocessor power delivery", in proc. Appl. Power Electron. Conf., Mar. 1999, pp. 1181-1187.
- [113] Julu Sun, Yuancheng Ren, Ming Xu and Fred C. Lee, "Light Load Efficiency Improvement for Laptop VRs", in proc. Appl. Power Electron. Conf., Feb. 25 2007-March 1 2007, pp. 120 – 126.
- [114] R. W. Erickson, D. Maksimovic, "Fundamentals of Power Electronics, 2nd Edition, 2001, Kluwer Academic Publishers.
- [115] L. Chai, C. Lopez, A. Shaikh, "Fine Line Printing Technologies for Microwave and Millimeter Wave Applications", *36th International Symposium on Microelectronic proceedings*, 2003, pp. ??.
- [116] Katsuhiko Naka, "Using LFC Technology, Murata Makes Automotive Ceramic Substrates", Asia Electronics Industry, vol. 10, serial number 103, April 2005, pp. 50-52.
- [117] Jerzy A. Owczarek and Frank L. Howland, "A Study of the Off-Contact Screen Printing Process- Part I: Mode of the Printing Process and Some Results Derived From Experiments", IEEE Trans. Components, Hybrids, and Manufacturing Tech., vol. 13. no. 2, June 1990, pp. 358-367.

[118] Jerzy A. Owczarek and Frank L. Howland, "A Study of the Off-Contact Screen Printing Process- Part II: Analysis of the Model of the Printing Process", IEEE Trans. Components, Hybrids, and Manufacturing Tech., vol. 13. no. 2, June 1990, pp. 368-375.

[119] <http://www.renesas.com>

[120] Renesas HAT2168H, silicon N channel power MOS FET, Rev. 7.00, 20 Sept 2005

[121] Renesas HAT2165H, silicon N channel power MOS FET, Rev. 6.00, 20 Sept 2005

[122] National Semiconductor Corporation, LM27222, High-speed 4.5 A Synchronous MOSFET Driver, Sept. 2004. Website: <http://www.national.com>.

[123] Surface Mount Schottky Power Rectifier, MBR130T1/D, Jul 2005, Rev. 2. Website: <http://onsemi.com>.

[124] Pun, A.L.L.; Yeung, T.; Lau, J.; Clement, J.R.; Su, D.K.; "Substrate noise coupling through planar spiral inductor", J. Solid-State Circuits, vol. 33, no. 6, Jun 1998, pp.877 – 884.

[125] Cheon Soo Kim, Piljae Park, Joung-Woo Park, Nam Hwang, Hyu Kyu Yu, "Deep trench guard technology to suppress coupling between inductors in silicon RF ICs", IEEE Microwave Symp. Digest, vol. 3, 20 - 25 May 2001, pp. 1873 – 1876.

[126] Chung-Ping Chien, A. F. Burnett, J. M. Cech, M. H. Tanielian, "The signal transmission characteristics of embedded microstrip transmission lines over a meshed ground plane in copper/polyimide multichip module", IEEE Trans. Components and Packaging Technologies, vol. 17, no. 4, Nov. 1994, pp. 578 – 583.

[127] T.S.D. Cheung, J. R. Long, "Shielded passive devices for silicon-based monolithic microwave and millimeter-wave integrated circuits" J. Solid State Circuits, vol. 41, no. 5, May 2006, pp. 1183 – 1200.

[128] Y. Ren, M. Xu, J. Zhou, Lee F. C., "Analytical loss model of power MOSFET", IEEE Trans. Pow. Electron. vol. 21, no. 2, pp. 310, Mar 2006.

[129] Datasheets of products of Enpirion, Inc. [online]. Available: <http://www.enpirion.com>

[130] Datasheets of products of Micrel, Inc. [online]. Available: <http://www.micrel.com>

[131] Datasheets of products of Fuji Electric, Inc. [online]. Available: <http://www.fujielectric.co.jp>

[132] Datasheets of products of Linear Technology, Inc. Available: <http://www.linear.com>

[133] David Morrison, "Regulators Embed Inductors to Save Space and Ease Use", Power Electronics Technology, July 2007, pp. 46-48.

[134] Y. Katayama, M. Edo, T. Denta, T. Kawashima, T. Ninomiya, "Optimum design method of CMOS IC for DC-DC converter that integrates power stage MOSFETs", in Proc. Power Electronics Specialists Conf., vol. 6, 20-25 June 2004, pp. 4486 – 4491.

- [135] Y. Katayama, S. Sugahara, H. Nakazawa, M. Edo, “High-power-density MHz-switching monolithic DC-DC converter with thin-film inductor”, in Proc. Power Electronics Specialists Conf., vol. 3, 18-23 June 2000, pp. 1485 – 1490.
- [136] W. G. Hurley, M. C. Duffy, S. O'Reilly, S. C. O'Mathuna, “Impedance formulas for planar magnetic structures with spiral windings”, IEEE Trans. Industrial Electronics, vol. 46, no. 2, April 1999, pp. 271 – 278.
- [137] J. M. Lopera, M. J. Prieto, A. M. Pernia, F. Nuno, M. J. M. De Graaf, J. W. Waanders, L. A. Barcia, “Design of integrated magnetic elements using thick-film technology”, IEEE Trans. Power Electronics, vol. 14, no. 3, May 1999, pp. 408 - 414
- [138] R. Hahn, S. Krumbholz, H. Reichl, “Low profile power inductors based on ferromagnetic LTCC technology”, in Proc. 56th Electronic Components and Technology Conf., 30 May-2 June 2006, pp. 528-533.
- [139] T. Mikura, K. Nakahara, K. Ikeda, K. Furukuwa, K. Onitsuka, “New substrate for micro DC-DC converter”, in Proc. 56th Electronic Components and Technology Conf., 30 May-2 June 2006, pp. 1326-1330.
- [140] Fuji Power Supply Control IC, Micro DC-DC Converter, FB 6831 Application Note, Rev. 0, July 2006, Fuji Electric Device Technology, Co., Ltd. Website: <http://www.fujielectric.com>
- [141] National Semiconductor Corporation, LM3218 650 mA Miniature, Adjustable, Step-Down DC-DC Converter for RF Power Amplifiers, 18 Mar 2008, Website: <http://www.national.com>
- [142] S. Bae, H. –M. Jung, J. –S. Moon, Y. Mano, “Embedded inductor using Ni-Zn ferrite film in polymer substrate”, in Proc. IEEE Int. Magnetics Conf., 4-8 April 2005, pp. 1767 – 1768.
- [143] Datasheets of products of Dupont, Inc. Available: http://www2.dupont.com/Pyralux/en_US
- [144] Renesas RJK0301DPB, silicon N channel power MOS FET, Rev. 9.00, 19 Apr 2006.